



PERMIT
Under the Environmental Conservation Law (ECL)

IDENTIFICATION INFORMATION

Permit Type: Air Title V Facility
Permit ID: 5-4154-00002/01743
Mod 0 Effective Date: 01/07/2008 Expiration Date: 01/06/2013

Mod 1 Effective Date: Expiration Date:

Permit Issued To:MPM SILICONES LLC
260 HUDSON RIVER RD
WATERFORD, NY 12188

Contact: SHAWN WILLIAMS
GENERAL ELECTRIC COMPANY
260 HUDSON RIVER RD
WATERFORD, NY 12188-2631
(518) 233-3608

Facility: MOMENTIVE PERFORMANCE MATERIALS
260 HUDSON RIVER RD
WATERFORD, NY 12188

Contact: JAMES PHIPPS
MOMENTIVE PERFORMANCE MATERIALS
260 HUDSON RIVER RD
WATERFORD, NY 12188
(518) 233-3432

Description:
Momentive Performance Materials operates a silicone production facility (sic 2821) located in Saratoga County, New York, in the town of Waterford. The plant is approximately 12 miles north of Albany. The site produces silicone products and other materials including resins, fluids, dispersions, emulsions, heat curing elastomers, room temperature vulcanizing (rtv) elastomers and fumed silica. The site has continuous and batch chemicals processes, compounding, finishing and packaging operations, and steam generation capability.

Major emissions include: Carbon Monoxide (CO), Sulfur Dioxide (SO₂), Volatile Organic Compounds (VOCs), Hazardous Air Pollutants (HAPs), Oxides of Nitrogen (NO_x), Particulate Mater (PM) and Particulate Mater less than 10 microns (PM-10).

Emission unit listing and a brief description:

C-27018: This unit consists of the following production areas: Methyl Chloride, Gaseous Dihydrolysis (GDH), Liquid Dihydrolysis (LDH), Siloxane Oil, the Area 38 tank farm, the B30 Polykettle systems, and the B24A MQ Resin system. The unit also includes the following control devices and their associated equipment: the MCS Vent Incinerator, MCS Vent Scrubber, the Fixed Box (#2) Hazardous Waste Incinerator, and the Rotary Kiln Hazardous Waste Incinerator. Sources in this unit include storage tanks, distillation columns, process vessels, Synthetic Organic Chemical Manufacturing Industry (SOCMI) distillation columns, SOCMI



reactors, and SOCM I wastewater. Applicable regulations for unit C-27018 include: the Hazardous Organic NESHAP (HON) under 40 CFR 63 Subparts F, G, and H, the Hazardous Waste Incinerator MACT under 40 CFR 63 Subpart EEE, the Miscellaneous Organic NESHAP under 40 CFR Subpart FFFF, New Source Performance Standards (NSPS) for SOCM I distillation columns (40 CFR 60 Subpart NNN), SOCM I reactors (40 CFR 60 Subpart RRR), and volatile organic liquid (VOL) storage tanks (40 CFR 60 Subpart Kb), Volatile Organic Compound Reasonably Available Control Technology (VOC RACT) under 6 NYCRR Subpart 212, sulfur fuel limitations under 6 NYCRR Subpart 225, VOC RACT for storage tanks under 6 NYCRR Subpart 229, and State Air Toxics under 6 NYCRR Subpart 212.

C-27035: Emission unit C-27035 is comprised of several aboveground storage tanks that are used to store acids. All of the tanks are located in the HCL Tank Farm. All but one of the tanks vents to a packed tower water scrubber (EP27035). One tank vents to an eductor (EP27039) which is piped to the chemical process sewer. The emission unit also contains three locations within the tank farm, which allow for scrapping of acid to the chemical process sewer. The applicable regulations are the State Air Toxics under 6 NYCRR Subpart 212, the Miscellaneous Organic NESHAP under 40 CFR Subpart FFFF, and New Source Performance Standards (NSPS) for volatile organic liquid (VOL) storage tanks under 40 CFR 60 Subpart Kb.

C-61007: Emission unit C-61007 includes the Silicon Grinding and Fines Passivation area. In the area, Silicon Grinding area, silicon metal is ground, screened, and transferred to silos. In the Fines Passivation area, mixers are used to mix fines to neutralize and harden the material. Processes include mixers, dust collectors, and an unloading station. Applicable regulations for this unit include emissions limitations for capping under Prevention of Significant Deterioration (40 CFR Subpart 52), the Miscellaneous Organic NESHAP under 40 CFR Subpart FFFF, and particulate emissions limitations under 6 NYCRR 212.

C-62008: Emission unit C-62008 includes all equipment associated with the methylchlorosilane (MCS) reactor systems (MCS II system, MCS III system and MCS IV system) that are not associated with the control devices in unit C-27018. Sources include process vessels, feed hoppers, and hot oil furnaces. Applicable regulations for this unit include emissions limitations for capping under Prevention of Significant Deterioration (40 CFR Subpart 52) and Non-Attainment New Source Review under 6 NYCRR 231-2, the Miscellaneous Organic NESHAP under 40 CFR Subpart FFFF, and particulate limitations under 6 NYCRR 212.

C-62014: This unit consists of sources in the Trichlorosilanes (TCS) and Fumed Silica production areas. The TCS area currently consists of exempt sources. The Fumed Silica area consists of a scrubber and various solids handling equipment. Applicable regulations include State Air Toxics under 6 NYCRR Subpart 212 and the Hydrochloric Acid Production MACT under NNNNN.

EGNRTR: This unit consists of emergency generator sources. They are subject to the Reciprocating Industrial Combustion Engine MACT of 40 CFR 63 Subpart ZZZZ.

F-INISH: This unit consists of intermediate and final production of silicone products and materials, including resins, fluids, dispersions, emulsions, heat curing elastomers, room temperature vulcanizing (rtv) elastomers, sealants, and treated fumed silica. Also includes various maintenance shops and individual maintenance sources (such as degreasers). Process sources include storage vessels, batch reactors, process tanks, mixers, feed hoppers, filter presses, drumming operations, liquid add stations, process strippers, unloading stations, packaging operations, maintenance degreasers, and all of the associated control equipment. Applicable regulations include the following: emissions limitations for capping under Prevention of Significant Deterioration (40 CFR Subpart 52) and Non-Attainment New Source Review



under 6 NYCRR 231-2, New Source Performance Standards (NSPS) for volatile organic liquid (VOL) storage tanks under 40 CFR 60 Subpart Kb, Volatile Organic Compound Reasonably Available Control Technology (VOC RACT) under 6 NYCRR Subpart 212, State Air Toxics under 6 NYCRR Subpart 212, VOC RACT for Storage Tanks Under 6 NYCRR 229, the Miscellaneous Organic NESHAP under 40 CFR Subpart FFFF, and VOC RACT for Part Cleaners under 6 NYCRR 226.

H-OFURN: This unit consists of the plant's hot oil furnaces not associated with MCS. These furnaces are subject to 6 NYCRR 227 and the Industrial Boiler MACT .

T-13004: Unit 13004 consists of various pilot plant processes located in Building 13. Sources include process vessels, filters, and local extraction discharges. The applicable regulations include State Air Toxics under 6 NYCRR Subpart 212.

T-14009: This unit consists of equipment in the facility's Pilot Plant, located in Buildings 14, 15 and 16. The Pilot Plant makes developmental/experimental products for evaluation, and scaled-down batches of problem production grades to develop process adjustments. Scaled down batches of commercial products are also made here. Processes are small-volume sources including process vessels, strippers, distillation columns, mixers, and reactors. The applicable regulations include State Air Toxics under 6 NYCRR Subpart 212.

U-28002: Emission Unit U28002 consists of Boilers 13 and 18 and a #2 Fuel Oil storage tank. Applicable regulations include emissions limitations for capping under Prevention of Significant Deterioration (40 CFR Subpart 52) and Non-Attainment New Source Review under 6 NYCRR 231-2, New Source Performance Standards (NSPS) for volatile organic liquid (VOL) storage tanks under 40 CFR 60 Subpart Kb, NSPS regulations for industrial boilers under 40 CFR 60 Subpart Db, NO_x RACT under 6 NYCRR 227-2, particulate limitations under 6 NYCRR 227-1, NO_x Budget regulations under 6 NYCRR 227-3 and 204, the Industrial Boiler MACT, NO_x CAIR rule during the ozone season under 6 NYCRR 243, and fuel limitations for sulfur under 6 NYCRR 225.

U-28003: Emission Unit U28003 consists of boilers 14, 15, 16, and 17. Applicable regulations include Prevention of Significant Deterioration (40 CFR Subpart 52) and Non-Attainment New Source Review under 6 NYCRR 231-2, NO_x RACT under 6 NYCRR 227-2, particulate limitations under 6 NYCRR 227-1, the Industrial Boiler MACT, and fuel limitations for sulfur under 6 NYCRR 225.

W-97004: This emission unit is the wastewater treatment process system of the waste handling area. The wastewater treatment plant is a physical/chemical treatment system consisting of pH neutralization, oil and grease separation, clarification, and air stripping operations. The applicable regulations are New Source Performance Standards (NSPS) for Volatile Organic Liquid (VOL) storage tanks under 40 CFR 60 Subpart Kb, State Air Toxics under 6 NYCRR Subpart 212, the Miscellaneous Organic NESHAP under 40 CFR Subpart FFFF, and Volatile Organic Compound Reasonably Available Control Technology (VOC RACT) under 6 NYCRR Subpart 212.

By acceptance of this permit, the permittee agrees that the permit is contingent upon strict compliance with the ECL, all applicable regulations, the General Conditions specified and any Special Conditions included as part of this permit.

Permit Administrator: WALTER L HAYNES
 DIVISION OF ENVIRONMENTAL PERMITS

New York State Department of Environmental Conservation
Facility DEC ID: 541540002



232 GOLF COURSE RD PO BOX 220
WARRENSBURG, NY 12885-0220

Authorized Signature: _____ Date: ___ / ___ / ____



Notification of Other State Permittee Obligations

Item A: Permittee Accepts Legal Responsibility and Agrees to Indemnification

The permittee expressly agrees to indemnify and hold harmless the Department of Environmental Conservation of the State of New York, its representatives, employees and agents ("DEC") for all claims, suits, actions, and damages, to the extent attributable to the permittee's acts or omissions in connection with the compliance permittee's undertaking of activities in connection with, or operation and maintenance of, the facility or facilities authorized by the permit whether in compliance or not in any compliance with the terms and conditions of the permit. This indemnification does not extend to any claims, suits, actions, or damages to the extent attributable to DEC's own negligent or intentional acts or omissions, or to any claims, suits, or actions naming the DEC and arising under article 78 of the New York Civil Practice Laws and Rules or any citizen suit or civil rights provision under federal or state laws.

Item B: Permittee's Contractors to Comply with Permit

The permittee is responsible for informing its independent contractors, employees, agents and assigns of their responsibility to comply with this permit, including all special conditions while acting as the permittee's agent with respect to the permitted activities, and such persons shall be subject to the same sanctions for violations of the Environmental Conservation Law as those prescribed for the permittee.

Item C: Permittee Responsible for Obtaining Other Required Permits

The permittee is responsible for obtaining any other permits, approvals, lands, easements and rights-of-way that may be required to carry out the activities that are authorized by this permit.

Item D: No Right to Trespass or Interfere with Riparian Rights

This permit does not convey to the permittee any right to trespass upon the lands or interfere with the riparian rights of others in order to perform the permitted work nor does it authorize the impairment of any rights, title, or interest in real or personal property held or vested in a person not a party to the permit.



LIST OF CONDITIONS

DEC GENERAL CONDITIONS

General Provisions

Facility Inspection by the Department
Relationship of this Permit to Other Department Orders and
Determinations
Applications for permit renewals, modifications and transfers
Applications for Permit Renewals and Modifications
Permit modifications, suspensions or revocations by the Department
Permit Modifications, Suspensions and Revocations by the Department

Facility Level

Submission of application for permit modification or renewal-REGION 5
SUBOFFICE - WARRENSBURG



DEC GENERAL CONDITIONS

****** General Provisions ******

For the purpose of your Title V permit, the following section contains state-only enforceable terms and conditions.

GENERAL CONDITIONS - Apply to ALL Authorized Permits.

Condition 1: Facility Inspection by the Department

Applicable State Requirement: ECL 19-0305

Item 1.1:

The permitted site or facility, including relevant records, is subject to inspection at reasonable hours and intervals by an authorized representative of the Department of Environmental Conservation (the Department) to determine whether the permittee is complying with this permit and the ECL. Such representative may order the work suspended pursuant to ECL 71-0301 and SAPA 401(3).

Item 1.2:

The permittee shall provide a person to accompany the Department's representative during an inspection to the permit area when requested by the Department.

Item 1.3:

A copy of this permit, including all referenced maps, drawings and special conditions, must be available for inspection by the Department at all times at the project site or facility. Failure to produce a copy of the permit upon request by a Department representative is a violation of this permit.

Condition 2: Relationship of this Permit to Other Department Orders and Determinations

Applicable State Requirement: ECL 3-0301.2(m)

Item 2.1:

Unless expressly provided for by the Department, issuance of this permit does not modify, supersede or rescind any order or determination previously issued by the Department or any of the terms, conditions or requirements contained in such order or determination.

Condition 3: Applications for permit renewals, modifications and transfers

Applicable State Requirement: 6NYCRR 621.11

Item 3.1:

The permittee must submit a separate written application to the Department for renewal, modification or transfer of this permit. Such application must include any forms or supplemental information the Department requires. Any renewal, modification or transfer granted by the Department must be in writing.

Item 3.2:

The permittee must submit a renewal application at least 180 days before expiration of permits for Title V Facility Permits, or at least 30 days before expiration of permits for State Facility Permits.

Item 3.3:



Permits are transferrable with the approval of the department unless specifically prohibited by the statute, regulation or another permit condition. Applications for permit transfer should be submitted prior to actual transfer of ownership.

Condition 4: Applications for Permit Renewals and Modifications

Applicable State Requirement: 6NYCRR 621.13

Item 4.1:

The permittee must submit a separate written application to the Department for renewal, modification or transfer of this permit. Such application must include any forms or supplemental information the Department requires. Any renewal, modification or transfer granted by the Department must be in writing.

Item 4.2:

The permittee must submit a renewal application at least 180 days before expiration of permits for Title V Facility Permits, or at least 30 days before expiration of permits for State Facility Permits.

Item 4.3:

Permits are transferrable with the approval of the department unless specifically prohibited by the statute, regulation or another permit condition. Applications for permit transfer should be submitted prior to actual transfer of ownership.

Condition 5: Permit modifications, suspensions or revocations by the Department

Applicable State Requirement: 6NYCRR 621.13

Item 5.1:

The Department reserves the right to modify, suspend, or revoke this permit in accordance with 6NYCRR Part 621. The grounds for modification, suspension or revocation include:

- a) materially false or inaccurate statements in the permit application or supporting papers;
- b) failure by the permittee to comply with any terms or conditions of the permit;
- c) exceeding the scope of the project as described in the permit application;
- d) newly discovered material information or a material change in environmental conditions, relevant technology or applicable law or regulations since the issuance of the existing permit;
- e) noncompliance with previously issued permit conditions, orders of the commissioner, any provisions of the Environmental Conservation Law or regulations of the Department related to the permitted activity.

Condition 6: Permit Modifications, Suspensions and Revocations by the Department

Applicable State Requirement: 6NYCRR 621.14

Item 6.1:

The Department reserves the right to modify, suspend, or revoke this permit in accordance with 6NYCRR Part 621. The grounds for modification, suspension or revocation include:

- a) materially false or inaccurate statements in the permit application or supporting papers;



- b) failure by the permittee to comply with any terms or conditions of the permit;
- c) exceeding the scope of the project as described in the permit application;
- d) newly discovered material information or a material change in environmental conditions, relevant technology or applicable law or regulations since the issuance of the existing permit;
- e) noncompliance with previously issued permit conditions, orders of the commissioner, any provisions of the Environmental Conservation Law or regulations of the Department related to the permitted activity.

****** Facility Level ******

**Condition 7: Submission of application for permit modification or renewal-REGION 5
SUBOFFICE - WARRENSBURG
Applicable State Requirement: 6NYCRR 621.6(a)**

Item 7.1:

Submission of applications for permit modification or renewal are to be submitted to:

NYSDEC Regional Permit Administrator
Region 5 Sub-office
Division of Environmental Permits
232 Golf Course Road, PO Box 220
Warrensburg, NY 12885-0220
(518) 623-1281



Permit Under the Environmental Conservation Law (ECL)

ARTICLE 19: AIR POLLUTION CONTROL - TITLE V PERMIT

IDENTIFICATION INFORMATION

Permit Issued To:MPM SILICONES LLC
260 HUDSON RIVER RD
WATERFORD, NY 12188

Facility: MOMENTIVE PERFORMANCE MATERIALS
260 HUDSON RIVER RD
WATERFORD, NY 12188

Authorized Activity By Standard Industrial Classification Code:
2819 - INDUSTRIAL INORGANIC CHEMICALS
2821 - PLASTICS MATERIALS AND RESINS
2822 - SYNTHETIC RUBBER
2869 - INDUSTRIAL ORGANIC CHEMICALS,NEC

Permit Effective Date:

Permit Expiration Date:



LIST OF CONDITIONS

DEC GENERAL CONDITIONS

General Provisions

- Facility Inspection by the Department
- Relationship of this Permit to Other Department Orders and Determinations
- Applications for permit renewals, modifications and transfers
- Applications for Permit Renewals and Modifications
- Permit modifications, suspensions or revocations by the Department
- Permit Modifications, Suspensions and Revocations by the Department

Facility Level

- Submission of application for permit modification or renewal-REGION 5 SUBOFFICE - WARRENSBURG

FEDERALLY ENFORCEABLE CONDITIONS

Facility Level

- 24 6NYCRR 201-6: Emission Unit Definition
- 1-1 6NYCRR 212.9(b): Compliance Certification
- 1-2 6NYCRR 212.9(b): Compliance Certification
- 1-3 6NYCRR 212.9(b): Compliance Certification
- 1-4 6NYCRR 212.9(b): Compliance Certification
- 1-5 6NYCRR 212.9(b): Compliance Certification
- 1-6 6NYCRR 212.9(b): Compliance Certification
- 1-7 6NYCRR 212.9(b): Compliance Certification
- 1-8 6NYCRR 212.9(b): Compliance Certification
- 1-9 6NYCRR 212.9(b): Compliance Certification
- 1-10 6NYCRR 212.9(b): Compliance Certification
- 1-11 6NYCRR 212.9(b): Compliance Certification
- 1-12 6NYCRR 212.9(b): Compliance Certification
- 1-13 6NYCRR 212.9(b): Compliance Certification
- 1-14 6NYCRR 212.9(b): Compliance Certification
- 1-15 6NYCRR 212.9(b): Compliance Certification
- 1-16 6NYCRR 212.9(b): Compliance Certification
- 1-17 6NYCRR 212.9(b): Compliance Certification
- 1-18 6NYCRR 212.9(b): Compliance Certification
- 1-19 40CFR 60.7(a), NSPS Subpart A: Compliance Certification
- 106 40CFR 60.7(a), NSPS Subpart A: Compliance Certification
- 146 40CFR 63.104, Subpart F: Compliance Certification
- 147 40CFR 63.104, Subpart F: Compliance Certification
- 150 40CFR 63.104(c), Subpart F: Compliance Certification
- 1-20 40CFR 63.139(c), Subpart G: Compliance Certification
- 189 40CFR 63.139(c), Subpart G: Compliance Certification
- 1-21 40CFR 63.140, Subpart G: Compliance Certification
- 191 40CFR 63.140, Subpart G: Compliance Certification
- 1-22 40CFR 63.143(e), Subpart G: Compliance Certification
- 192 40CFR 63.143(e), Subpart G: Compliance Certification
- 1-23 40CFR 63.143(g), Subpart G: Compliance Certification
- 1-24 40CFR 63.145(h), Subpart G: Compliance Certification
- 1-25 40CFR 63.998(a)(2), Subpart SS: Compliance Certification
- 1-26 40CFR 63.998(a)(2), Subpart SS: Compliance Certification



- 258 40CFR 63.998(a)(2), Subpart SS: Compliance Certification
 - 264 40CFR 63.998(c)(3), Subpart SS: Compliance Certification
 - 1-28 40CFR 63.1203(a)(5)(i), Subpart EEE: Compliance Certification
 - 307 40CFR 63.1203(a)(5)(i), Subpart EEE: Compliance Certification
 - 1-29 40CFR 63.1206(c), Subpart EEE: Compliance Certification
 - 314 40CFR 63.1206(c), Subpart EEE: Compliance Certification
 - 316 40CFR 63.1207, Subpart EEE: Compliance Certification
 - 1-30 40CFR 63.1209(j)(2), Subpart EEE: Compliance Certification
 - 1-31 40CFR 63.1209(j)(2), Subpart EEE: Compliance Certification
 - 1-32 40CFR 63.1209(j)(2), Subpart EEE: Compliance Certification
 - 1-33 40CFR 63.1209(j)(2), Subpart EEE: Compliance Certification
 - 1-34 40CFR 63.1209(j)(2), Subpart EEE: Compliance Certification
 - 331 40CFR 63.1209(j)(2), Subpart EEE: Compliance Certification
 - 334 40CFR 63.1209(j)(2), Subpart EEE: Compliance Certification
 - 1-35 40CFR 63.1209(j)(3), Subpart EEE: Compliance Certification
 - 336 40CFR 63.1209(j)(3), Subpart EEE: Compliance Certification
 - 1-36 40CFR 63.1209(j)(4), Subpart EEE: Compliance Certification
 - 1-37 40CFR 63.1209(j)(4), Subpart EEE: Compliance Certification
 - 1-38 40CFR 63.1209(j)(4), Subpart EEE: Compliance Certification
 - 344 40CFR 63.1209(j)(4), Subpart EEE: Compliance Certification
 - 1-39 40CFR 63.1209(m)(1)(i)(B)(1), Subpart EEE: Compliance Certification
 - 353 40CFR 63.1209(m)(1)(i)(B)(1), Subpart EEE: Compliance Certification
 - 385 40CFR 63.1209(o)(3)(v), Subpart EEE: Compliance Certification
 - 1-27 40CFR 63.1209(p), Subpart EEE: Compliance Certification
 - 389 40CFR 63.1209(p), Subpart EEE: Compliance Certification
 - 1-40 40CFR 63.2450(f), Subpart FFFF: Compliance Certification
 - 1-41 40CFR 63.2455(a), Subpart FFFF: Compliance Certification
 - 1-42 40CFR 63.2455(a), Subpart FFFF: Compliance Certification
 - 1-43 40CFR 63.2455(a), Subpart FFFF: Compliance Certification
 - 1-44 40CFR 63.2455(a), Subpart FFFF: Compliance Certification
 - 1-45 40CFR 63.2455(a), Subpart FFFF: Compliance Certification
 - 420 40CFR 63.2455(a), Subpart FFFF: Compliance Certification
 - 421 40CFR 63.2455(a), Subpart FFFF: Compliance Certification
 - 1-46 40CFR 63.2465(a), Subpart FFFF: Compliance Certification
 - 1-47 40CFR 63.2465(a), Subpart FFFF: Compliance Certification
 - 1-48 40CFR 63.2465(a), Subpart FFFF: Compliance Certification
 - 1-49 40CFR 63.2465(a), Subpart FFFF: Compliance Certification
 - 1-50 40CFR 63.2465(a), Subpart FFFF: Compliance Certification
 - 430 40CFR 63.2465(a), Subpart FFFF: Compliance Certification
 - 431 40CFR 63.2465(a), Subpart FFFF: Compliance Certification
 - 432 40CFR 63.2465(a), Subpart FFFF: Compliance Certification
 - 433 40CFR 63.2465(a), Subpart FFFF: Compliance Certification
 - 434 40CFR 63.2465(a), Subpart FFFF: Compliance Certification
 - 435 40CFR 63.2465(a), Subpart FFFF: Compliance Certification
 - 436 40CFR 63.2465(a), Subpart FFFF: Compliance Certification
 - 437 40CFR 63.2465(a), Subpart FFFF: Compliance Certification
- Emission Unit Level**
- 476 6NYCRR 201-6: Emission Point Definition By Emission Unit
 - 477 6NYCRR 201-6: Process Definition By Emission Unit

EU=C-27018,Proc=400,ES=FUGTV

- 1-51 40CFR 63.162(c), Subpart H: General standards - identification of equipment



EU=C-27018,Proc=406,ES=HXCWW

- 1-52 40CFR 63.104, Subpart F: Delay of repair provisions for heat exchange systems
- 1-53 40CFR 63.104, Subpart F: Provisions for handling leaks found in heat exchanger coolant

STATE ONLY ENFORCEABLE CONDITIONS

Facility Level

- 479 ECL 19-0301: Contaminant List
- 484 : Compliance Demonstration
- 486 : Compliance Demonstration
- 493 : Compliance Demonstration
- 494 : Compliance Demonstration
- 495 : Compliance Demonstration
- 496 : Compliance Demonstration
- 501 : Compliance Demonstration
- 504 : Compliance Demonstration
- 506 : Compliance Demonstration
- 509 : Compliance Demonstration



FEDERALLY ENFORCEABLE CONDITIONS

****** Facility Level ******

NOTIFICATION OF GENERAL PERMITTEE OBLIGATIONS

The items listed below are not subject to the annual compliance certification requirements under Title V. Permittees may also have other obligations under regulations of general applicability.

Item A: Emergency Defense - 6NYCRR Part 201-1.5

An emergency constitutes an affirmative defense to an action brought for noncompliance with emissions limitations or permit conditions for all facilities in New York State.

(a) The affirmative defense of emergency shall be demonstrated through properly signed, contemporaneous operating logs, or other relevant evidence that:

(1) An emergency occurred and that the facility owner and/or

operator can identify the cause(s) of the emergency;

(2) The equipment at the permitted facility causing the emergency was at the time being properly operated;

(3) During the period of the emergency the facility owner and/or operator took all reasonable steps to minimize levels of emissions that exceeded the emission standards, or other requirements in the permit; and

(4) The facility owner and/or operator notified the Department

within two working days after the event occurred. This notice must contain a description of the emergency, any steps taken to mitigate emissions, and corrective actions taken.

(b) In any enforcement proceeding, the facility owner and/or operator seeking to establish the occurrence of an emergency has the burden of proof.

(c) This provision is in addition to any emergency or upset provision contained in any applicable requirement.

Item B: Public Access to Recordkeeping for Title V Facilities - 6NYCRR Part 201-1.10(b)

The Department will make available to the public any permit application, compliance plan, permit, and monitoring and compliance certification report pursuant to Section 503(e) of the Act, except for information entitled to confidential treatment pursuant to 6NYCRR Part 616 - Public Access to records and Section 114(c) of the Act.



- Item C: Timely Application for the Renewal of Title V Permits - 6 NYCRR Part 201-6.3(a)(4)**
Owners and/or operators of facilities having an issued Title V permit shall submit a complete application at least 180 days, but not more than eighteen months, prior to the date of permit expiration for permit renewal purposes.
- Item D: Certification by a Responsible Official - 6 NYCRR Part 201-6.3(d)(12)**
Any application, form, report or compliance certification required to be submitted pursuant to the federally enforceable portions of this permit shall contain a certification of truth, accuracy and completeness by a responsible official. This certification shall state that based on information and belief formed after reasonable inquiry, the statements and information in the document are true, accurate, and complete.
- Item E: Requirement to Comply With All Conditions - 6 NYCRR Part 201-6.5(a)(2)**
The permittee must comply with all conditions of the Title V facility permit. Any permit non-compliance constitutes a violation of the Act and is grounds for enforcement action; for permit termination, revocation and reissuance, or modification; or for denial of a permit renewal application.
- Item F: Permit Revocation, Modification, Reopening, Reissuance or Termination, and Associated Information Submission Requirements - 6 NYCRR Part 201-6.5(a)(3)**
This permit may be modified, revoked, reopened and reissued, or terminated for cause. The filing of a request by the permittee for a permit modification, revocation and reissuance, or termination, or of a notification of planned changes or anticipated noncompliance does not stay any permit condition.
- Item G: Cessation or Reduction of Permitted Activity Not a Defense - 6 NYCRR Part 201-6.5(a)(5)**
It shall not be a defense for a permittee in an enforcement action to claim that a cessation or reduction in the permitted activity would have been necessary in order to maintain compliance with the conditions of this permit.
- Item H: Property Rights - 6 NYCRR Part 201-6.5(a)(6)**
This permit does not convey any property rights of any sort or any exclusive privilege.
- Item I: Severability - 6 NYCRR Part 201-6.5(a)(9)**



If any provisions, parts or conditions of this permit are found to be invalid or are the subject of a challenge, the remainder of this permit shall continue to be valid.

Item J: Permit Shield - 6 NYCRR Part 201-6.5(g)

All permittees granted a Title V facility permit shall be covered under the protection of a permit shield, except as provided under 6 NYCRR Subpart 201-6. Compliance with the conditions of the permit shall be deemed compliance with any applicable requirements as of the date of permit issuance, provided that such applicable requirements are included and are specifically identified in the permit, or the Department, in acting on the permit application or revision, determines in writing that other requirements specifically identified are not applicable to the major stationary source, and the permit includes the determination or a concise summary thereof. Nothing herein shall preclude the Department from revising or revoking the permit pursuant to 6 NYCRR Part 621 or from exercising its summary abatement authority. Nothing in this permit shall alter or affect the following:

- i. The ability of the Department to seek to bring suit on behalf of the State of New York, or the Administrator to seek to bring suit on behalf of the United States, to immediately restrain any person causing or contributing to pollution presenting an imminent and substantial endangerment to public health, welfare or the environment to stop the emission of air pollutants causing or contributing to such pollution;
- ii. The liability of a permittee of the Title V facility for any violation of applicable requirements prior to or at the time of permit issuance;
- iii. The applicable requirements of Title IV of the Act;
- iv. The ability of the Department or the Administrator to obtain information from the permittee concerning the ability to enter, inspect and monitor the facility.

Item K: Reopening for Cause - 6 NYCRR Part 201-6.5(i)

This Title V permit shall be reopened and revised under any of the following circumstances:

- i. If additional applicable requirements under the Act become applicable where this permit's remaining term is three or more years, a reopening shall be completed not later than 18 months after promulgation of the applicable requirement. No such reopening is required if the



effective date of the requirement is later than the date on which this permit is due to expire, unless the original permit or any of its terms and conditions has been extended by the Department pursuant to the provisions of Part 201-6.7 and Part 621.

ii. The Department or the Administrator determines that the permit contains a material mistake or that inaccurate statements were made in establishing the emissions standards or other terms or conditions of the permit.

iii. The Department or the Administrator determines that the Title V permit must be revised or reopened to assure compliance with applicable requirements.

iv. If the permitted facility is an "affected source" subject to the requirements of Title IV of the Act, and additional requirements (including excess emissions requirements) become applicable. Upon approval by the Administrator, excess emissions offset plans shall be deemed to be incorporated into the permit.

Proceedings to reopen and issue Title V facility permits shall follow the same procedures as apply to initial permit issuance but shall affect only those parts of the permit for which cause to reopen exists.

Reopenings shall not be initiated before a notice of such intent is provided to the facility by the Department at least thirty days in advance of the date that the permit is to be reopened, except that the Department may provide a shorter time period in the case of an emergency.

Item L: Permit Exclusion - ECL 19-0305

The issuance of this permit by the Department and the receipt thereof by the Applicant does not and shall not be construed as barring, diminishing, adjudicating or in any way affecting any legal, administrative or equitable rights or claims, actions, suits, causes of action or demands whatsoever that the Department may have against the Applicant for violations based on facts and circumstances alleged to have occurred or existed prior to the effective date of this permit, including, but not limited to, any enforcement action authorized pursuant to the provisions of applicable federal law, the Environmental Conservation Law of the State of New York (ECL) and Chapter III of the Official Compilation of the Codes, Rules and Regulations of the State of New York (NYCRR). The issuance of this permit also shall not in any way affect pending or future enforcement actions under the Clean Air Act brought by the United States or any person.



Item M: Federally Enforceable Requirements - 40 CFR 70.6(b)

All terms and conditions in this permit required by the Act or any applicable requirement, including any provisions designed to limit a facility's potential to emit, are enforceable by the Administrator and citizens under the Act. The Department has, in this permit, specifically designated any terms and conditions that are not required under the Act or under any of its applicable requirements as being enforceable under only state regulations.

The following conditions are subject to annual compliance certification requirements for Title V permits only.

Condition 24: Emission Unit Definition

Effective between the dates of 01/07/2008 and Permit Expiration Date

Applicable Federal Requirement:6NYCRR 201-6

Item 24.1(From Mod 1):

The facility is authorized to perform regulated processes under this permit for:

Emission Unit: C-27018

Emission Unit Description:

Chemical operations and sources requiring incineration control under MON MACT. The MCS Vent incinerator, MCS vent scrubber, Fixed Box incinerator no. 2, and the rotary kiln incinerator are included in this unit.

Building(s): 21
23
24
24A
27
28
30
34
35
36
37
38
48
55
57
61
62
70
71
76
78
85



96A

Item 24.2(From Mod 1):

The facility is authorized to perform regulated processes under this permit for:

Emission Unit: C-27035

Emission Unit Description:

Emission unit C-27035 is comprised of several aboveground storage tanks which are used to store acids. The emission unit also contains three locations within the tank farm which allow for scrapping of acid to the chemical process sewer.

Building(s): 27

Item 24.3(From Mod 1):

The facility is authorized to perform regulated processes under this permit for:

Emission Unit: E-GNRTR

Emission Unit Description:

This unit consists of emergency generators that operate less than 500 hours per year each.

Item 24.4(From Mod 1):

The facility is authorized to perform regulated processes under this permit for:

Emission Unit: F-INISH

Emission Unit Description:

Finishing - intermediate and final production of silicone products and materials including resins, fluids, dispersions, emulsions, heat curing elastomers, room temperature vulcanizing (rtv) elastomers, sealants, and treated fumed silica. Also includes various maintenance shops and individual maintenance sources (such as degreasers).

Building(s): 21
23
24
24A
27
28
30
32
35
36
37
38
48
55
57
61
62
70
71
76



78
85
96A

Item 24.5(From Mod 1):

The facility is authorized to perform regulated processes under this permit for:

Emission Unit: H-OFURN

Emission Unit Description:

This unit consists of additional hot oil furnaces not already included in another emission unit.

Building(s): 21
35

Item 24.6(From Mod 1):

The facility is authorized to perform regulated processes under this permit for:

Emission Unit: U-28002

Emission Unit Description:

Emission Unit U28002 consists of Boilers 13 and 18 and a #2 Fuel Oil storage tank.

Building(s): 21
28
35

Item 24.7(From Mod 0):

The facility is authorized to perform regulated processes under this permit for:

Emission Unit: C-61007

Emission Unit Description:

Silicon grinding area and fines passivation area. In the silicon grinding area, silicon metal is ground, screened, and transferred to silos. In the fines passivation area, mixers are used to mix fines to neutralize and harden the material.

Building(s): 61

Item 24.8(From Mod 0):

The facility is authorized to perform regulated processes under this permit for:

Emission Unit: C-62008

Emission Unit Description:

Chemops - MCSII, MCSIII and MCSIV operations. All equipment associated with the MCSII, MCSIII and MCSIV production operations, with the exception of the MCS vent scrubbers and MCS vent incinerator.

Building(s): 55
57
62
65

Item 24.9(From Mod 0):

The facility is authorized to perform regulated processes under this permit for:



Emission Unit: C-62014

Emission Unit Description:

This unit consists of sources in the trichlorosilanes (TCS) and fumed silica production areas.

Building(s): 68

Item 24.10(From Mod 0):

The facility is authorized to perform regulated processes under this permit for:

Emission Unit: T-13004

Emission Unit Description:

Vapors and particulates are vented to the atmosphere outside of building 13 at different emissions points. These include process, filter, and local extraction discharges.

Building(s): 13

Item 24.11(From Mod 0):

The facility is authorized to perform regulated processes under this permit for:

Emission Unit: U-28003

Emission Unit Description:

Emission Unit U28003 consists of boilers 14, 15, 16, and 17.

Building(s): 28

Item 24.12(From Mod 0):

The facility is authorized to perform regulated processes under this permit for:

Emission Unit: W-97004

Emission Unit Description:

This Emission Unit is the wastewater treatment process system of the waste handling area. The wastewater treatment plant is a physical/chemical treatment system consisting of pH neutralization, oil and grease separation, clarification, and air stripping operations.

Building(s): 93

95

96A

97

**Condition 1-1: Compliance Certification
Effective for entire length of Permit**

Applicable Federal Requirement:6NYCRR 212.9(b)

Item 1-1.1:

The Compliance Certification activity will be performed for the facility:

The Compliance Certification applies to:

Emission Unit: F-INISH

Emission Point: 32040



Emission Unit: F-INISH Emission Point: 32042

Emission Unit: F-INISH Emission Point: 32044

Emission Unit: F-INISH Emission Point: 32049

Emission Unit: F-INISH Emission Point: 32050

Regulated Contaminant(s):
CAS No: 000556-67-2 OCTAMETHYLCYCLOTETRA SILOXANE

Item 1-1.2:

Compliance Certification shall include the following monitoring:

Monitoring Type: MONITORING OF PROCESS OR CONTROL
DEVICE PARAMETERS AS SURROGATE

Monitoring Description:

Each condenser's outlet gas temperature will be monitored when the ERP of non-VOCs (Octamethylcyclotetra Siloxane) exceeds 10 lb/hr and when "A" rated contaminant ERPs exceeds 1 lb/hr. This process emits through five emission points 32040, 32042, 32044, 32049 and 32050. Engineering calculations will be used as evidence of compliance with control efficiency when the measured parameters exceeds the upper limit of monitoring.

Parameter Monitored: TEMPERATURE

Upper Permit Limit: 30 degrees Centigrade (or Celsius)

Monitoring Frequency: PER BATCH OF PRODUCT/RAW MATERIAL
CHANGE

Averaging Method: MAXIMUM - NOT TO BE EXCEEDED AT ANY
TIME (INSTANTANEOUS/DISCRETE OR GRAB)

Reporting Requirements: SEMI-ANNUALLY (CALENDAR)

Reports due 30 days after the reporting period.

Subsequent reports are due every 6 calendar month(s).

**Condition 1-2: Compliance Certification
Effective for entire length of Permit**

Applicable Federal Requirement:6NYCRR 212.9(b)

Item 1-2.1:

The Compliance Certification activity will be performed for the facility:

The Compliance Certification applies to:

Emission Unit: F-INISH Emission Point: 32026

Emission Unit: F-INISH Emission Point: 32027

Regulated Contaminant(s):
CAS No: 000556-67-2 OCTAMETHYLCYCLOTETRA SILOXANE

Item 1-2.2:



Compliance Certification shall include the following monitoring:

Monitoring Type: MONITORING OF PROCESS OR CONTROL
DEVICE PARAMETERS AS SURROGATE

Monitoring Description:

Condenser outlet temperature will be monitored once per batch to ensure sufficient control efficiency. This process emits through two emission points 32026 and 32027. The upper limit of monitoring ensures compliance with all process batch operations. Engineering calculations will be used as evidence of compliance with contaminant control efficiency when the measured temperature rises above the upper limit of monitoring.

Parameter Monitored: TEMPERATURE

Upper Permit Limit: 67 degrees Centigrade (or Celsius)

Monitoring Frequency: PER BATCH OF PRODUCT/RAW MATERIAL
CHANGE

Averaging Method: AVERAGING METHOD - SEE MONITORING
DESCRIPTION

Reporting Requirements: SEMI-ANNUALLY (CALENDAR)

Reports due 30 days after the reporting period.

Subsequent reports are due every 6 calendar month(s).

**Condition 1-3: Compliance Certification
Effective for entire length of Permit**

Applicable Federal Requirement: 6NYCRR 212.9(b)

Item 1-3.1:

The Compliance Certification activity will be performed for the facility:

The Compliance Certification applies to:

Emission Unit: C-27018

Emission Point: 24945

Emission Unit: C-27018

Emission Point: 24944

Regulated Contaminant(s):

CAS No: 007647-01-0

HYDROGEN CHLORIDE

Item 1-3.2:

Compliance Certification shall include the following monitoring:

Monitoring Type: MONITORING OF PROCESS OR CONTROL
DEVICE PARAMETERS AS SURROGATE

Monitoring Description:

High acid scrubber water flow will be recorded (on/off)
for each batch to ensure sufficient control efficiency.

Parameter Monitored: VOLUMETRIC FLOW RATE

Lower Permit Limit: 64 gallons per minute

Monitoring Frequency: PER BATCH OF PRODUCT/RAW MATERIAL
CHANGE



Averaging Method: MINIMUM - NOT TO FALL BELOW STATED
VALUE AT ANY TIME

Reporting Requirements: SEMI-ANNUALLY (CALENDAR)

Reports due 30 days after the reporting period.

Subsequent reports are due every 6 calendar month(s).

Condition 1-4: Compliance Certification
Effective for entire length of Permit

Applicable Federal Requirement:6NYCRR 212.9(b)

Item 1-4.1:

The Compliance Certification activity will be performed for the facility:

The Compliance Certification applies to:

Emission Unit: F-INISH

Emission Point: 32028

Regulated Contaminant(s):

CAS No: 000107-46-0

HEXAMETHYLDISILOXANE

Item 1-4.2:

Compliance Certification shall include the following monitoring:

Monitoring Type: MONITORING OF PROCESS OR CONTROL
DEVICE PARAMETERS AS SURROGATE

Monitoring Description:

Scrubber water flow during stripping will be monitored to ensure sufficient control efficiency. The lower limit of monitoring ensures compliance with all process batch operations. Engineering calculations will be used as evidence of compliance with contaminant control efficiency when the measured flow rate falls below the lower limit of monitoring.

Parameter Monitored: VOLUMETRIC FLOW RATE

Lower Permit Limit: 10 gallons per minute

Monitoring Frequency: PER BATCH OF PRODUCT/RAW MATERIAL
CHANGE

Averaging Method: MINIMUM - NOT TO FALL BELOW STATED
VALUE AT ANY TIME

Reporting Requirements: SEMI-ANNUALLY (CALENDAR)

Reports due 30 days after the reporting period.

Subsequent reports are due every 6 calendar month(s).

Condition 1-5: Compliance Certification
Effective for entire length of Permit

Applicable Federal Requirement:6NYCRR 212.9(b)

Item 1-5.1:

The Compliance Certification activity will be performed for the facility:

The Compliance Certification applies to:



Emission Unit: C-27018

Emission Point: 62005

Regulated Contaminant(s):

CAS No: 007647-01-0

HYDROGEN CHLORIDE

Item 1-5.2:

Compliance Certification shall include the following monitoring:

Monitoring Type: MONITORING OF PROCESS OR CONTROL
DEVICE PARAMETERS AS SURROGATE

Monitoring Description:

The tower water flow (ES-62EST) is monitored to ensure sufficient control efficiency. Engineering calculations will be used as evidence of compliance with control efficiency when the measured flow rate falls below the lower limit of monitoring.

Parameter Monitored: VOLUMETRIC FLOW RATE

Lower Permit Limit: 90 gallons per minute

Monitoring Frequency: CONTINUOUS

Averaging Method: 24-HOUR AVERAGE

Reporting Requirements: SEMI-ANNUALLY (CALENDAR)

Reports due 30 days after the reporting period.

Subsequent reports are due every 6 calendar month(s).

**Condition 1-6: Compliance Certification
Effective for entire length of Permit**

Applicable Federal Requirement: 6NYCRR 212.9(b)

Item 1-6.1:

The Compliance Certification activity will be performed for the facility:

The Compliance Certification applies to:

Emission Unit: F-INISH

Emission Point: 37016

Regulated Contaminant(s):

CAS No: 000067-64-1

DIMETHYL KETONE

Item 1-6.2:

Compliance Certification shall include the following monitoring:

Monitoring Type: MONITORING OF PROCESS OR CONTROL
DEVICE PARAMETERS AS SURROGATE

Monitoring Description:

For grade 88476 (main process) the condenser outlet gas temperature will be maintained to ensure sufficient control efficiency. The upper limit of monitoring ensures compliance with all process batch operations. Engineering calculations will be used as evidence of compliance with contaminant control efficiency when the measured temperature rises above the upper limit of monitoring.



Parameter Monitored: TEMPERATURE
Upper Permit Limit: 41 degrees Centigrade (or Celsius)
Monitoring Frequency: PER BATCH OF PRODUCT/RAW MATERIAL CHANGE
Averaging Method: MAXIMUM - NOT TO BE EXCEEDED AT ANY TIME (INSTANTANEOUS/DISCRETE OR GRAB)
Reporting Requirements: SEMI-ANNUALLY (CALENDAR)
Reports due 30 days after the reporting period.
Subsequent reports are due every 6 calendar month(s).

Condition 1-7: Compliance Certification
Effective for entire length of Permit

Applicable Federal Requirement:6NYCRR 212.9(b)

Item 1-7.1:

The Compliance Certification activity will be performed for the facility:
The Compliance Certification applies to:

Emission Unit: C-27018 Emission Point: 62005

Regulated Contaminant(s):
CAS No: 007647-01-0 HYDROGEN CHLORIDE

Item 1-7.2:

Compliance Certification shall include the following monitoring:

Monitoring Type: MONITORING OF PROCESS OR CONTROL DEVICE PARAMETERS AS SURROGATE

Monitoring Description:

The Venturi water flow (ES-62EVS) is monitored to ensure sufficient control efficiency. Engineering calculations will be used as evidence of compliance with control efficiency when the measured flow rate falls below the lower limit of monitoring.

Parameter Monitored: VOLUMETRIC FLOW RATE
Lower Permit Limit: 60 gallons per minute
Monitoring Frequency: CONTINUOUS
Averaging Method: 24-HOUR AVERAGE
Reporting Requirements: SEMI-ANNUALLY (CALENDAR)
Reports due 30 days after the reporting period.
Subsequent reports are due every 6 calendar month(s).

Condition 1-8: Compliance Certification
Effective for entire length of Permit

Applicable Federal Requirement:6NYCRR 212.9(b)

Item 1-8.1:

The Compliance Certification activity will be performed for the facility:
The Compliance Certification applies to:



Emission Unit: C-27018

Emission Point: 35031

Regulated Contaminant(s):

CAS No: 000541-05-9

HEXAMETHYLCYCLOTRISILOXANE

Item 1-8.2:

Compliance Certification shall include the following monitoring:

Monitoring Type: MONITORING OF PROCESS OR CONTROL
DEVICE PARAMETERS AS SURROGATE

Monitoring Description:

Scrubber water flow rate will be monitored to ensure it is greater than or equal to 3 gallons per minute. Engineering calculations will be used as evidence of compliance with control efficiency when the measured flow rate falls below the lower limit of monitoring.

Parameter Monitored: VOLUMETRIC FLOW RATE

Lower Permit Limit: 3 gallons per minute

Monitoring Frequency: PER SHIFT

Averaging Method: 24-HOUR AVERAGE

Reporting Requirements: SEMI-ANNUALLY (CALENDAR)

Reports due 30 days after the reporting period.

Subsequent reports are due every 6 calendar month(s).

**Condition 1-9: Compliance Certification
Effective for entire length of Permit**

Applicable Federal Requirement: 6NYCRR 212.9(b)

Item 1-9.1:

The Compliance Certification activity will be performed for the facility:

The Compliance Certification applies to:

Emission Unit: C-27018

Emission Point: 71001

Regulated Contaminant(s):

CAS No: 000067-64-1

DIMETHYL KETONE

CAS No: 000124-70-9

SILANE, DICHLOROETHENYLMETHYL

CAS No: 001066-35-9

SILANE, CHLORODIMETHYL

CAS No: 001185-55-3

METHYLTRIMETHOXY SILANE

CAS No: 000075-94-5

SILANE, TRICHLOROETHENYL

Item 1-9.2:

Compliance Certification shall include the following monitoring:

Monitoring Type: RECORD KEEPING/MAINTENANCE PROCEDURES

Monitoring Description:

Water scrubber flow creates the proper vacuum to operate the process and removes air contaminants. Water flow to the scrubber is recorded (on/off) to ensure sufficient control efficiency. The lower limit of monitoring ensures compliance with all process batch operations. Engineering



calculations will be used as evidence of compliance with contaminant control efficiency when the measured flow rate falls below the lower limit of monitoring.

Monitoring Frequency: PER BATCH OF PRODUCT/RAW MATERIAL CHANGE

Reporting Requirements: SEMI-ANNUALLY (CALENDAR)

Reports due 30 days after the reporting period.

Subsequent reports are due every 6 calendar month(s).

Condition 1-10: Compliance Certification
Effective for entire length of Permit

Applicable Federal Requirement:6NYCRR 212.9(b)

Item 1-10.1:

The Compliance Certification activity will be performed for the facility:

The Compliance Certification applies to:

Emission Unit: F-INISH

Emission Point: 85008

Regulated Contaminant(s):

CAS No: 000556-67-2

OCTAMETHYLCYCLOTETRA SILOXANE

Item 1-10.2:

Compliance Certification shall include the following monitoring:

Monitoring Type: MONITORING OF PROCESS OR CONTROL DEVICE PARAMETERS AS SURROGATE

Monitoring Description:

Outlet temperature of condensing column 85TST will be monitored to ensure sufficient control efficiency. The lower limit of monitoring ensures compliance with all process batch operations. Engineering calculations will be used as evidence of compliance with contaminant control efficiency when the measured parameter exceeds the upper limit of monitoring.

Parameter Monitored: TEMPERATURE

Upper Permit Limit: 75 degrees Centigrade (or Celsius)

Monitoring Frequency: PER BATCH OF PRODUCT/RAW MATERIAL CHANGE

Averaging Method: MAXIMUM - NOT TO BE EXCEEDED AT ANY TIME (INSTANTANEOUS/DISCRETE OR GRAB)

Reporting Requirements: SEMI-ANNUALLY (CALENDAR)

Reports due 30 days after the reporting period.

Subsequent reports are due every 6 calendar month(s).

Condition 1-11: Compliance Certification
Effective for entire length of Permit

Applicable Federal Requirement:6NYCRR 212.9(b)



Item 1-11.1:

The Compliance Certification activity will be performed for the facility:
The Compliance Certification applies to:

Emission Unit: C-27018 Emission Point: 31041

Regulated Contaminant(s):
CAS No: 007664-41-7 AMMONIA

Item 1-11.2:

Compliance Certification shall include the following monitoring:

Monitoring Type: MONITORING OF PROCESS OR CONTROL
DEVICE PARAMETERS AS SURROGATE

Monitoring Description:

Water flow to the scrubbers will be monitored to ensure sufficient control efficiency. The lower limit of monitoring ensures compliance with all process batch operations. Engineering calculations will be used as evidence of compliance with contaminant control efficiency when the measured flow rate falls below the lower limit of monitoring.

Parameter Monitored: VOLUMETRIC FLOW RATE

Lower Permit Limit: 2.4 gallons per minute

Monitoring Frequency: PER BATCH OF PRODUCT/RAW MATERIAL
CHANGE

Averaging Method: MINIMUM - NOT TO FALL BELOW STATED
VALUE AT ANY TIME

Reporting Requirements: SEMI-ANNUALLY (CALENDAR)

Reports due 30 days after the reporting period.

Subsequent reports are due every 6 calendar month(s).

Condition 1-12: Compliance Certification
Effective for entire length of Permit

Applicable Federal Requirement:6NYCRR 212.9(b)

Item 1-12.1:

The Compliance Certification activity will be performed for the facility:
The Compliance Certification applies to:

Emission Unit: F-INISH Emission Point: 24947

Emission Unit: F-INISH Emission Point: 24946

Regulated Contaminant(s):
CAS No: 000064-17-5 ETHYL ALCOHOL (ETHANOL)
CAS No: 000067-56-1 METHYL ALCOHOL
CAS No: 000067-63-0 ISOPROPYL ALCOHOL
CAS No: 000067-64-1 DIMETHYL KETONE
CAS No: 000100-41-4 ETHYLBENZENE
CAS No: 000108-88-3 TOLUENE



CAS No: 001330-20-7 XYLENE, M, O & P MIXT.
CAS No: 000556-67-2 OCTAMETHYLCYCLOTETRA SILOXANE

Item 1-12.2:

Compliance Certification shall include the following monitoring:

Monitoring Type: MONITORING OF PROCESS OR CONTROL
DEVICE PARAMETERS AS SURROGATE

Monitoring Description:

Water flow for eductor scrubber (24SRC) will be recorded (on/off) to ensure sufficient control efficiency. This process is controlled by one eductor scrubber which emits through two emission points 24946 and 24947. The lower limit of monitoring ensures compliance with all process batch operations.

Parameter Monitored: VOLUMETRIC FLOW RATE

Lower Permit Limit: 9 gallons per minute

Monitoring Frequency: PER BATCH OF PRODUCT/RAW MATERIAL
CHANGE

Averaging Method: MINIMUM - NOT TO FALL BELOW STATED
VALUE AT ANY TIME

Reporting Requirements: SEMI-ANNUALLY (CALENDAR)

Reports due 30 days after the reporting period.

Subsequent reports are due every 6 calendar month(s).

**Condition 1-13: Compliance Certification
Effective for entire length of Permit**

Applicable Federal Requirement: 6NYCRR 212.9(b)

Item 1-13.1:

The Compliance Certification activity will be performed for the facility:

The Compliance Certification applies to:

Emission Unit: F-INISH Emission Point: 71013

Regulated Contaminant(s):
CAS No: 000075-79-6 METHYLTRICHLOROSILANE

Item 1-13.2:

Compliance Certification shall include the following monitoring:

Monitoring Type: RECORD KEEPING/MAINTENANCE PROCEDURES

Monitoring Description:

Water flow to the scrubber is recorded (on/off) to ensure sufficient control efficiency.

Monitoring Frequency: PER BATCH OF PRODUCT/RAW MATERIAL
CHANGE

Reporting Requirements: SEMI-ANNUALLY (CALENDAR)

Reports due 30 days after the reporting period.

Subsequent reports are due every 6 calendar month(s).



Condition 1-14: Compliance Certification
Effective for entire length of Permit

Applicable Federal Requirement:6NYCRR 212.9(b)

Item 1-14.1:

The Compliance Certification activity will be performed for the facility:
The Compliance Certification applies to:

Emission Unit: C-27018 Emission Point: 27018

Regulated Contaminant(s):
CAS No: 000074-87-3 METHYL CHLORIDE

Item 1-14.2:

Compliance Certification shall include the following monitoring:

Monitoring Type: MONITORING OF PROCESS OR CONTROL
DEVICE PARAMETERS AS SURROGATE

Monitoring Description:

The water flow to the scrubber is monitored to ensure the scrubber is operating at the required control efficiency. Engineering calculations will be used as evidence of compliance with control efficiency when the measured flow rate falls below the lower limit of monitoring.

Parameter Monitored: VOLUMETRIC FLOW RATE

Lower Permit Limit: 8 gallons per minute

Monitoring Frequency: CONTINUOUS

Averaging Method: 24-HOUR AVERAGE

Reporting Requirements: SEMI-ANNUALLY (CALENDAR)

Reports due 30 days after the reporting period.

Subsequent reports are due every 6 calendar month(s).

Condition 1-15: Compliance Certification
Effective for entire length of Permit

Applicable Federal Requirement:6NYCRR 212.9(b)

Item 1-15.1:

The Compliance Certification activity will be performed for the facility:
The Compliance Certification applies to:

Emission Unit: C-27018 Emission Point: 62011

Regulated Contaminant(s):
CAS No: 068479-14-1 SILANE, CHLORO METHYL DERIVS

Item 1-15.2:

Compliance Certification shall include the following monitoring:

Monitoring Type: MONITORING OF PROCESS OR CONTROL



DEVICE PARAMETERS AS SURROGATE

Monitoring Description:

The Venturi water flow (ES-62WVS) is monitored to ensure sufficient control efficiency. Engineering calculations will be used as evidence of compliance with control efficiency when the measured flow rate falls below the lower limit of monitoring.

Parameter Monitored: VOLUMETRIC FLOW RATE

Lower Permit Limit: 125 gallons per minute

Monitoring Frequency: CONTINUOUS

Averaging Method: 24-HOUR AVERAGE

Reporting Requirements: SEMI-ANNUALLY (CALENDAR)

Reports due 30 days after the reporting period.

Subsequent reports are due every 6 calendar month(s).

**Condition 1-16: Compliance Certification
Effective for entire length of Permit**

Applicable Federal Requirement:6NYCRR 212.9(b)

Item 1-16.1:

The Compliance Certification activity will be performed for the facility:

The Compliance Certification applies to:

Emission Unit: C-27018

Emission Point: 35006

Regulated Contaminant(s):

CAS No: 000541-05-9

HEXAMETHYLCYCLOTTRISILOXANE

CAS No: 007647-01-0

HYDROGEN CHLORIDE

CAS No: 000556-67-2

OCTAMETHYLCYCLOTETRA SILOXANE

Item 1-16.2:

Compliance Certification shall include the following monitoring:

Monitoring Type: MONITORING OF PROCESS OR CONTROL
DEVICE PARAMETERS AS SURROGATE

Monitoring Description:

The water flow to the scrubber is monitored to ensure the scrubber is operating at the required control efficiency.

Parameter Monitored: VOLUMETRIC FLOW RATE

Lower Permit Limit: 0.5 gallons per minute

Monitoring Frequency: CONTINUOUS

Averaging Method: 24-HOUR AVERAGE

Reporting Requirements: SEMI-ANNUALLY (CALENDAR)

Reports due 30 days after the reporting period.

Subsequent reports are due every 6 calendar month(s).

**Condition 1-17: Compliance Certification
Effective for entire length of Permit**

Applicable Federal Requirement:6NYCRR 212.9(b)



Item 1-17.1:

The Compliance Certification activity will be performed for the facility:

The Compliance Certification applies to:

Emission Unit: C-27018

Emission Point: 23002

Regulated Contaminant(s):

CAS No: 000107-46-0

HEXAMETHYLDISILOXANE

CAS No: 007647-01-0

HYDROGEN CHLORIDE

CAS No: 063148-62-9

SILOXANES AND SILICONES,DI-ME

Item 1-17.2:

Compliance Certification shall include the following monitoring:

Monitoring Type: MONITORING OF PROCESS OR CONTROL
DEVICE PARAMETERS AS SURROGATE

Monitoring Description:

Water flow rate to the scrubber will be monitored to meet required control efficiency. The lower limit of monitoring ensures compliance with all process operations.

Engineering calculations will be used as evidence of compliance with VOC control efficiency when the measured flow rate falls below the lower limit of monitoring.

Parameter Monitored: VOLUMETRIC FLOW RATE

Lower Permit Limit: 20 gallons per minute

Monitoring Frequency: CONTINUOUS

Averaging Method: 24-HOUR AVERAGE

Reporting Requirements: SEMI-ANNUALLY (CALENDAR)

Reports due 30 days after the reporting period.

Subsequent reports are due every 6 calendar month(s).

Condition 1-18: Compliance Certification
Effective for entire length of Permit

Applicable Federal Requirement:6NYCRR 212.9(b)

Item 1-18.1:

The Compliance Certification activity will be performed for the facility:

The Compliance Certification applies to:

Emission Unit: C-27018

Emission Point: 62011

Regulated Contaminant(s):

CAS No: 068479-14-1

SILANE, CHLORO METHYL DERIVS

Item 1-18.2:

Compliance Certification shall include the following monitoring:

Monitoring Type: MONITORING OF PROCESS OR CONTROL
DEVICE PARAMETERS AS SURROGATE

Monitoring Description:



The tower water flow (62WST) is monitored to ensure sufficient control efficiency. Engineering calculations will be used as evidence of compliance with control efficiency when the measured flow rate falls below the lower limit of monitoring.

Parameter Monitored: VOLUMETRIC FLOW RATE

Lower Permit Limit: 90 gallons per minute

Monitoring Frequency: CONTINUOUS

Averaging Method: 24-HOUR AVERAGE

Reporting Requirements: SEMI-ANNUALLY (CALENDAR)

Reports due 30 days after the reporting period.

Subsequent reports are due every 6 calendar month(s).

Condition 1-19: Compliance Certification
Effective for entire length of Permit

Applicable Federal Requirement: 40CFR 60.7(a), NSPS Subpart A

Item 1-19.1:

The Compliance Certification activity will be performed for the facility:

The Compliance Certification applies to:

Emission Unit: H-OFURN

Process: 418

Emission Unit: H-OFURN

Process: 426

Emission Unit: U-28002

Process: 410

Emission Unit: U-28002

Process: 411

Item 1-19.2:

Compliance Certification shall include the following monitoring:

Monitoring Type: RECORD KEEPING/MAINTENANCE PROCEDURES

Monitoring Description:

This facility currently does not have the fuel oil line connected to Boiler #18 and therefore, cannot operate Process 411. The facility also has not replaced the burners of the 21 or 35 Hot Oil Furnaces of Process 426. After this Process becomes operable, the certification will become applicable to Process 411 and 426.

Any owner or operator subject to this part shall furnish the Administrator with the following information:

1) a notification of the date construction or reconstruction commenced, post marked no later than



- 30 days after such date;
- 2) a notification of the anticipated date of initial start up, post marked not more than 60 days not less than 30 days prior to such date;
- 3) a notification of the actual date of initial start up, post marked within 15 days after such date;
- 4) a notification of any physical or operational change to an existing facility which may increase the emission rate of any air pollutant to which a standard applies, unless the change is specifically exempted under this part. The notice shall be post marked 60 days or as soon as practicable before the change is commenced and shall include information describing the precise nature of the change, present and proposed emission control systems, productive capability of the facility before and after the change, and the expected completion date of the change. The Administrator may request additional information regarding the change;
- 5) a notification of any physical or operational change to an existing facility which may increase the emission rate of any air pollutant to which a standard applies, unless the change is specifically exempted under 40 CFR Part 60. The notice shall be post marked 60 days or as soon as practicable before the change is commenced and shall include information describing the precise nature of the change, present and proposed emission control systems, productivity capability of the facility before and after the change, and the expected completion date of the change. The Administrator and/or this Department may request additional information regarding the change.

Monitoring Frequency: AS REQUIRED - SEE PERMIT MONITORING DESCRIPTION

Reporting Requirements: AS REQUIRED - SEE MONITORING DESCRIPTION

Condition 106: Compliance Certification
Effective between the dates of 01/07/2008 and Permit Expiration Date

Applicable Federal Requirement: 40CFR 60.7(a), NSPS Subpart A

Expired by Mod 1

Item 106.1:

The Compliance Certification activity will be performed for the facility:
The Compliance Certification applies to:

Emission Unit: U-28002
Process: 410

Emission Unit: U-28002
Process: 411

Item 106.2:



Compliance Certification shall include the following monitoring:

Monitoring Type: RECORD KEEPING/MAINTENANCE PROCEDURES

Monitoring Description:

This facility currently does not have the fuel oil line connected to Boiler #18 and therefore, cannot operate Process 411. After this Process becomes operable, the certification will become applicable to Process 411.

Any owner or operator subject to this part shall furnish the Administrator with the following information:

- 1) a notification of the date construction or reconstruction commenced, post marked no later than 30 days after such date;
- 2) a notification of the anticipated date of initial start up, post marked not more than 60 days not less than 30 days prior to such date;
- 3) a notification of the actual date of initial start up, post marked within 15 days after such date;
- 4) a notification of any physical or operational change to an existing facility which may increase the emission rate of any air pollutant to which a standard applies, unless the change is specifically exempted under this part. The notice shall be post marked 60 days or as soon as practicable before the change is commenced and shall include information describing the precise nature of the change, present and proposed emission control systems, productive capability of the facility before and after the change, and the expected completion date of the change. The Administrator may request additional information regarding the change;
- 5) a notification of any physical or operational change to an existing facility which may increase the emission rate of any air pollutant to which a standard applies, unless the change is specifically exempted under 40 CFR Part 60. The notice shall be post marked 60 days or as soon as practicable before the change is commenced and shall include information describing the precise nature of the change, present and proposed emission control systems, productivity capability of the facility before and after the change, and the expected completion date of the change. The Administrator and/or this Department may request additional information regarding the change.

Monitoring Frequency: AS REQUIRED - SEE PERMIT MONITORING DESCRIPTION

Reporting Requirements: AS REQUIRED - SEE MONITORING DESCRIPTION

Condition 146: Compliance Certification



Effective between the dates of 05/10/2008 and Permit Expiration Date

Applicable Federal Requirement:40CFR 63.104, Subpart F

Expired by Mod 1

Item 146.1:

The Compliance Certification activity will be performed for the facility:

The Compliance Certification applies to:

Emission Unit: C-27018

Process: 406

Regulated Contaminant(s):

CAS No: 0NY100-00-0 HAP

Item 146.2:

Compliance Certification shall include the following monitoring:

Monitoring Type: RECORD KEEPING/MAINTENANCE PROCEDURES

Monitoring Description:

If a leak is detected, it shall be repaired as soon as practical but not later than 45 calendar days after the owner/operator is notified of the results indicating a leak. The owner/operator shall confirm the repair within 7 days of the repair or startup, whichever is later.

The owner/operator shall retain the following records:

- records of any leaks detected
- monitoring data indicating the presence of a leak
- date(s) of the leak's detection
- date(s) of efforts to repair leak(s)
- method and date of confirmation of leak(s)

Monitoring Frequency: AS REQUIRED - SEE PERMIT MONITORING DESCRIPTION

Reporting Requirements: AS REQUIRED - SEE MONITORING DESCRIPTION

Condition 147: Compliance Certification

Effective between the dates of 05/10/2008 and Permit Expiration Date

Applicable Federal Requirement:40CFR 63.104, Subpart F

Expired by Mod 1

Item 147.1:

The Compliance Certification activity will be performed for the facility:

The Compliance Certification applies to:

Emission Unit: C-27018

Process: 406

Regulated Contaminant(s):



CAS No: 0NY100-00-0 HAP

Item 147.2:

Compliance Certification shall include the following monitoring:

Monitoring Type: RECORD KEEPING/MAINTENANCE PROCEDURES

Monitoring Description:

Delay of repair is allowed for heat exchanger system leaks in the following situations:

- 1) If the equipment that is isolated from the process,
or
- 2) If the repair is technically infeasible without a shutdown, and one of the following is true:
 - a) A shutdown is expected within two months after the delay of repair is determined to be necessary. Repair may be delayed until that shutdown.
 - b) A shutdown is not expected within the next two months and a shutdown to repair the leaking equipment would result in greater emissions than delaying repair. In this case the owner/operator shall document the items listed in 63.104(e)(2)(i)(A) and (B) and delay the repair until the next shutdown.
 - c) A shutdown is not expected within the next two months and the owner/operator does not determine that the shutdown would result in greater emissions than a delay of repair. The owner/operator may delay the repair for 120 days. The owner/owner shall demonstrate that the necessary parts or personnel were not available

The owner/operator shall submit the following in the next semiannual report:

- 1) the presence of a leak and the date the leak was detected
- 2) whether the leak has been repaired
- 3) the reason(s) for the delay of repair
- 4) the expected date of repair if not repaired
- 5) the date of successful repair of the leak

If a leak is detected, it shall be repaired as soon as practical but not later than 45 calendar days after the owner/operator is notified of the results indicating a leak. The owner/operator shall confirm the repair within 7 days of the repair or startup, whichever is later.

The owner/operator shall retain the following records:

- records of any leaks detected
- monitoring data indicating the presence of a leak
- date(s) of the leak's detection
- date(s) of efforts to repair leak(s)
- method and date of confirmation of leak(s)

Monitoring Frequency: AS REQUIRED - SEE PERMIT MONITORING DESCRIPTION

Reporting Requirements: AS REQUIRED - SEE MONITORING DESCRIPTION



Condition 150: Compliance Certification
Effective between the dates of 05/10/2008 and Permit Expiration Date

Applicable Federal Requirement: 40CFR 63.104(c), Subpart F

Expired by Mod 1

Item 150.1:

The Compliance Certification activity will be performed for the facility:
The Compliance Certification applies to:

Emission Unit: C-27018
Process: 406

Regulated Contaminant(s):
CAS No: 0NY100-00-0 HAP

Item 150.2:

Compliance Certification shall include the following monitoring:

Monitoring Type: RECORD KEEPING/MAINTENANCE PROCEDURES

Monitoring Description:

The owner or operator who elects to comply with the requirement of paragraph (a) of this section by monitoring using a surrogate indicator of heat exchange system leaks shall comply with the requirements specified in paragraphs (c)(1) through (c)(3) of this section. Surrogate indicators that could be used to develop an acceptable monitoring program are ion specific electrode monitoring, pH, conductivity or other representative indicators.

(1) The owner or operator shall prepare and implement a monitoring plan that documents the procedures that will be used to detect leaks of process fluids into cooling water. The plan shall require monitoring of one or more surrogate indicators or monitoring of one or more process parameters or other conditions that indicate a leak. Monitoring that is already being conducted for other purposes may be used to satisfy the requirements of this section. The plan shall include the information specified in paragraphs (c)(1)(i) and (c)(1)(ii) of this section.

(2) If a substantial leak is identified by methods other than those described in the monitoring plan and the method(s) specified in the plan could not detect the leak, the owner or operator shall revise the plan and document the basis for the changes. The owner or operator shall complete the revisions to the plan no later than 180 days after discovery of the leak.

(3) The owner or operator shall maintain, at all times, the monitoring plan that is currently in use. The current plan shall be maintained on-site, or shall be accessible from a central location by computer or other means that provides access within 2 hours after a request. If the monitoring plan is superseded, the owner or operator shall



retain the most recent superseded plan at least until 5 years from the date of its creation. The superseded plan shall be retained on-site (or accessible from a central location by computer or other means that provides access within two hours after a request) for at least 6 months after its creation.

Monitoring Frequency: AS REQUIRED - SEE PERMIT MONITORING DESCRIPTION

Reporting Requirements: AS REQUIRED - SEE MONITORING DESCRIPTION

**Condition 1-20: Compliance Certification
Effective for entire length of Permit**

Applicable Federal Requirement: 40CFR 63.139(c), Subpart G

Item 1-20.1:

The Compliance Certification activity will be performed for the facility:
The Compliance Certification applies to:

Emission Unit: C-27018 Process: 422	Emission Source: WTPAS
Emission Unit: C-27018 Process: 423	Emission Source: WTPAS
Emission Unit: C-27018 Process: 424	Emission Source: WTPAS
Emission Unit: C-27018 Process: 425	Emission Source: WTPAS

Item 1-20.2:

Compliance Certification shall include the following monitoring:

Monitoring Type: RECORD KEEPING/MAINTENANCE PROCEDURES

Monitoring Description:

The control device shall be designed and operated in accordance with paragraph (c)(5) of this section.

(5) Any other control device used shall, alone or in combination with other control devices, reduce the total organic compound emissions, less methane and ethane, or total organic hazardous air pollutants emissions vented to the control device by 95 percent by weight or greater or achieve an outlet total organic compound concentration, less methane and ethane, or total organic hazardous air pollutants concentration of 20 parts per million by volume, whichever is less stringent. The 20 parts per million by volume performance standard is not applicable to compliance with the provisions of §63.134 or §63.135 of this subpart.



Emissions from this source will be vented to the RKI (RKIAB) or Fixed Box #2 Incinerator (FBIAB).

Monitoring Frequency: AS REQUIRED - SEE PERMIT MONITORING DESCRIPTION

Reporting Requirements: AS REQUIRED - SEE MONITORING DESCRIPTION

Condition 189: Compliance Certification
Effective between the dates of 05/10/2008 and Permit Expiration Date

Applicable Federal Requirement:40CFR 63.139(c), Subpart G

Expired by Mod 1

Item 189.1:

The Compliance Certification activity will be performed for the facility:
The Compliance Certification applies to:

Emission Unit: C-27018

Process: 213

Emission Source: 40KEQ

Item 189.2:

Compliance Certification shall include the following monitoring:

Monitoring Type: RECORD KEEPING/MAINTENANCE PROCEDURES

Monitoring Description:

The control device shall be designed and operated in accordance with paragraph (c)(5) of this section.

(5) Any other control device used shall, alone or in combination with other control devices, reduce the total organic compound emissions, less methane and ethane, or total organic hazardous air pollutants emissions vented to the control device by 95 percent by weight or greater or achieve an outlet total organic compound concentration, less methane and ethane, or total organic hazardous air pollutants concentration of 20 parts per million by volume, whichever is less stringent. The 20 parts per million by volume performance standard is not applicable to compliance with the provisions of §63.134 or §63.135 of this subpart.

Emissions from these sources (PKSDT, 30WWT, and 20KEQ) will be vented to the RKI (RKIAB) or Fixed Box #2 Incinerator (FBIAB).

Monitoring Frequency: AS REQUIRED - SEE PERMIT MONITORING DESCRIPTION

Reporting Requirements: AS REQUIRED - SEE MONITORING DESCRIPTION

Condition 1-21: Compliance Certification
Effective for entire length of Permit

Applicable Federal Requirement:40CFR 63.140, Subpart G



Item 1-21.1:

The Compliance Certification activity will be performed for the facility:

The Compliance Certification applies to:

Emission Unit: C-27018

Process: 422

Emission Source: WTPAS

Emission Unit: C-27018

Process: 423

Emission Source: WTPAS

Emission Unit: C-27018

Process: 424

Emission Source: WTPAS

Emission Unit: C-27018

Process: 425

Emission Source: WTPAS

Item 1-21.2:

Compliance Certification shall include the following monitoring:

Monitoring Type: RECORD KEEPING/MAINTENANCE PROCEDURES

Monitoring Description:

(a) Delay of repair of equipment for which a control equipment failure or a gap, crack, tear, or hole has been identified, is allowed if the repair is technically infeasible without a shutdown, as defined in §63.101 of subpart F of this part, or if the owner or operator determines that emissions of purged material from immediate repair would be greater than the emissions likely to result from delay of repair. Repair of this equipment shall occur by the end of the next shutdown.

(b) Delay of repair of equipment for which a control equipment failure or a gap, crack, tear, or hole has been identified, is allowed if the equipment is emptied or is no longer used to treat or manage Group 1 wastewater streams or residuals removed from Group 1 wastewater streams.

(c) Delay of repair of equipment for which a control equipment failure or a gap, crack, tear, or hole has been identified is also allowed if additional time is necessary due to the unavailability of parts beyond the control of the owner or operator. Repair shall be completed as soon as practical. The owner or operator who uses this provision shall comply with the requirements of §63.147(b)(7) to document the reasons that the delay of repair was necessary.

Monitoring Frequency: AS REQUIRED - SEE PERMIT MONITORING DESCRIPTION

Reporting Requirements: AS REQUIRED - SEE MONITORING DESCRIPTION

Condition 191: Compliance Certification



Effective between the dates of 05/10/2008 and Permit Expiration Date

Applicable Federal Requirement:40CFR 63.140, Subpart G

Expired by Mod 1

Item 191.1:

The Compliance Certification activity will be performed for the facility:
The Compliance Certification applies to:

Emission Unit: C-27018

Process: 213

Emission Source: 40KEQ

Item 191.2:

Compliance Certification shall include the following monitoring:

Monitoring Type: RECORD KEEPING/MAINTENANCE PROCEDURES

Monitoring Description:

- (a) Delay of repair of equipment for which a control equipment failure or a gap, crack, tear, or hole has been identified, is allowed if the repair is technically infeasible without a shutdown, as defined in §63.101 of subpart F of this part, or if the owner or operator determines that emissions of purged material from immediate repair would be greater than the emissions likely to result from delay of repair. Repair of this equipment shall occur by the end of the next shutdown.
- (b) Delay of repair of equipment for which a control equipment failure or a gap, crack, tear, or hole has been identified, is allowed if the equipment is emptied or is no longer used to treat or manage Group 1 wastewater streams or residuals removed from Group 1 wastewater streams.
- (c) Delay of repair of equipment for which a control equipment failure or a gap, crack, tear, or hole has been identified is also allowed if additional time is necessary due to the unavailability of parts beyond the control of the owner or operator. Repair shall be completed as soon as practical. The owner or operator who uses this provision shall comply with the requirements of §63.147(b)(7) to document the reasons that the delay of repair was necessary.

Monitoring Frequency: AS REQUIRED - SEE PERMIT MONITORING DESCRIPTION

Reporting Requirements: AS REQUIRED - SEE MONITORING DESCRIPTION

Condition 1-22: Compliance Certification
Effective for entire length of Permit

Applicable Federal Requirement:40CFR 63.143(e), Subpart G

Item 1-22.1:



The Compliance Certification activity will be performed for the facility:
The Compliance Certification applies to:

Emission Unit: C-27018 Process: 422	Emission Source: WTPAS
Emission Unit: C-27018 Process: 423	Emission Source: WTPAS
Emission Unit: C-27018 Process: 424	Emission Source: WTPAS
Emission Unit: C-27018 Process: 425	Emission Source: WTPAS

Item 1-22.2:

Compliance Certification shall include the following monitoring:

Monitoring Type: RECORD KEEPING/MAINTENANCE PROCEDURES

Monitoring Description:

(e) Except as provided in paragraphs (e)(4) and (e)(5) of this section, for each control device used to comply with the requirements of §§63.133 through 63.139 of this subpart, the owner or operator shall comply with the requirements in §63.139(d) of this subpart, and with the requirements specified in paragraph (e)(1), (e)(2), or (e)(3) of this section.

(1) The owner or operator shall comply with the monitoring requirements specified in table 13 of this subpart; or

(2) The owner or operator shall use an organic monitoring device installed at the outlet of the control device and equipped with a continuous recorder. Continuous recorder is defined in §63.111 of this subpart; or

(3) The owner or operator shall request approval to monitor parameters other than those specified in paragraphs (e)(1) and (e)(2) of this section. The request shall be submitted according to the procedures specified in §63.151(f) of this subpart, and shall include a description of planned reporting and recordkeeping procedures. The Administrator will specify appropriate reporting and recordkeeping requirements as part of the review of the permit application or by other appropriate means. Emissions from this source will be vented to the RKI (RKIAB) or FBI #2 (FBIAB).

Monitoring Frequency: AS REQUIRED - SEE PERMIT MONITORING DESCRIPTION

Reporting Requirements: AS REQUIRED - SEE MONITORING DESCRIPTION

Condition 192: Compliance Certification
Effective between the dates of 05/10/2008 and Permit Expiration Date



Applicable Federal Requirement:40CFR 63.143(e), Subpart G

Expired by Mod 1

Item 192.1:

The Compliance Certification activity will be performed for the facility:

The Compliance Certification applies to:

Emission Unit: C-27018

Process: 213

Emission Source: 40KEQ

Item 192.2:

Compliance Certification shall include the following monitoring:

Monitoring Type: RECORD KEEPING/MAINTENANCE PROCEDURES

Monitoring Description:

(e) Except as provided in paragraphs (e)(4) and (e)(5) of this section, for each control device used to comply with the requirements of §§63.133 through 63.139 of this subpart, the owner or operator shall comply with the requirements in §63.139(d) of this subpart, and with the requirements specified in paragraph (e)(1), (e)(2), or (e)(3) of this section.

(1) The owner or operator shall comply with the monitoring requirements specified in table 13 of this subpart; or

(2) The owner or operator shall use an organic monitoring device installed at the outlet of the control device and equipped with a continuous recorder. Continuous recorder is defined in §63.111 of this subpart; or

(3) The owner or operator shall request approval to monitor parameters other than those specified in paragraphs (e)(1) and (e)(2) of this section. The request shall be submitted according to the procedures specified in §63.151(f) of this subpart, and shall include a description of planned reporting and recordkeeping procedures. The Administrator will specify appropriate reporting and recordkeeping requirements as part of the review of the permit application or by other appropriate means.

Monitoring Frequency: AS REQUIRED - SEE PERMIT MONITORING DESCRIPTION

Reporting Requirements: AS REQUIRED - SEE MONITORING DESCRIPTION

**Condition 1-23: Compliance Certification
Effective for entire length of Permit**

Applicable Federal Requirement:40CFR 63.143(g), Subpart G

Item 1-23.1:

The Compliance Certification activity will be performed for the facility:

The Compliance Certification applies to:



Emission Unit: C-27018

Process: 422

Emission Source: WTPAS

Emission Unit: C-27018

Process: 423

Emission Source: WTPAS

Emission Unit: C-27018

Process: 424

Emission Source: WTPAS

Emission Unit: C-27018

Process: 425

Emission Source: WTPAS

Item 1-23.2:

Compliance Certification shall include the following monitoring:

Monitoring Type: RECORD KEEPING/MAINTENANCE PROCEDURES

Monitoring Description:

Monitoring equipment shall be installed, calibrated, and maintained according to the manufacturer's specifications or other written procedures that provide adequate assurance that the equipment would reasonably be expected to monitor accurately.

Monitoring Frequency: AS REQUIRED - SEE PERMIT MONITORING DESCRIPTION

Reporting Requirements: AS REQUIRED - SEE MONITORING DESCRIPTION

**Condition 1-24: Compliance Certification
Effective for entire length of Permit**

Applicable Federal Requirement: 40CFR 63.145(h), Subpart G

Item 1-24.1:

The Compliance Certification activity will be performed for the facility:

The Compliance Certification applies to:

Emission Unit: C-27018

Emission Unit: C-27035

Emission Unit: F-INISH

Regulated Contaminant(s):

CAS No: 0NY100-00-0 HAP

Item 1-24.2:

Compliance Certification shall include the following monitoring:

Monitoring Type: MONITORING OF PROCESS OR CONTROL DEVICE PARAMETERS AS SURROGATE

Monitoring Description:

When Group 1 wastewaters are treated using the biosystems, the Volatile Suspended Solids (VSS) will be



sampled quarterly to demonstrate enhanced biological treatment. If the VSS concentration falls below 1000 mg/L, WATER9 modeling will be used to demonstrate 99% removal by biological treatment.

Parameter Monitored: VOLATILE SUSPENDED SOLIDS

Upper Permit Limit: 1000 milligrams per liter

Monitoring Frequency: QUARTERLY

Averaging Method: MAXIMUM - NOT TO EXCEED STATED VALUE -
SEE MONITORING DESCRIPTION

Reporting Requirements: AS REQUIRED - SEE MONITORING DESCRIPTION

Condition 1-25: Compliance Certification
Effective for entire length of Permit

Applicable Federal Requirement: 40CFR 63.998(a)(2), Subpart SS

Item 1-25.1:

The Compliance Certification activity will be performed for the facility:
The Compliance Certification applies to:

Emission Unit: C-27018

Emission Unit: C-27035

Emission Unit: F-INISH

Regulated Contaminant(s):
CAS No: 0NY100-00-0 HAP

Item 1-25.2:

Compliance Certification shall include the following monitoring:

Monitoring Type: RECORD KEEPING/MAINTENANCE PROCEDURES

Monitoring Description:

(B) Nonflare combustion device. Where an owner or operator subject to the provisions of this paragraph seeks to demonstrate compliance with a percent reduction requirement or a parts per million by volume requirement using a nonflare combustion device the information specified in (a)(2)(ii)(B)(1) through (6) of this section shall be recorded.

(1)

(2)

(3) For a boiler or process heater with a design heat input capacity less than 44 megawatts and a vent stream that is not introduced with or as the primary fuel, record the fire box temperature averaged over the full period of the performance test.

(4)

(5) For a boiler or process heater, record a description of the location at which the vent stream is introduced into the boiler or process heater.



(6) For a boiler or process heater with a design heat input capacity of less than 44 megawatts and where the process vent stream is introduced with combustion air or used as a secondary fuel and is not mixed with the primary fuel, record the percent reduction of organic regulated material or TOC, or the concentration of regulated material or TOC (parts per million by volume, by compound) determined as specified in §63.997(e)(2)(iii) at the outlet of the combustion device.

(C)

(D) Halogen reduction devices. When using a scrubber following a combustion device to control a halogenated vent stream, record the information specified in paragraphs (a)(2)(ii)(D)(1) through (3) of this section.

(1) The percent reduction or scrubber outlet mass emission rate of total hydrogen halides and halogens as specified in §63.997(e)(3).

(2) The pH of the scrubber effluent averaged over the time period of the performance test; and

(3) The scrubber liquid-to-gas ratio averaged over the time period of the performance test.

Monitoring Frequency: AS REQUIRED - SEE PERMIT MONITORING DESCRIPTION

Reporting Requirements: AS REQUIRED - SEE MONITORING DESCRIPTION

**Condition 1-26: Compliance Certification
Effective for entire length of Permit**

Applicable Federal Requirement:40CFR 63.998(a)(2), Subpart SS

Item 1-26.1:

The Compliance Certification activity will be performed for the facility:
The Compliance Certification applies to:

Emission Unit: C-27018

Emission Unit: C-27035

Emission Unit: F-INISH

Regulated Contaminant(s):
CAS No: 0NY100-00-0 HAP

Item 1-26.2:

Compliance Certification shall include the following monitoring:

Monitoring Type: RECORD KEEPING/MAINTENANCE PROCEDURES

Monitoring Description:

(i) Upon request, the owner or operator shall make available to the Administrator such records as may be necessary to determine the conditions of performance tests



performed pursuant to §§63.988(b), 63.990(b), 63.994(b), or 63.995(b).

(ii) Nonflare control device and halogen reduction device performance test records.

(A) General requirements. Each owner or operator subject to the provisions of this subpart shall keep up-to-date, readily accessible continuous records of the data specified in paragraphs (a)(2)(ii)(B) through (C) of this section, as applicable, measured during each performance test performed pursuant to §63.988(b), §63.990(b), §63.994(b), or §63.995(b), and also include that data in the Notification of Compliance Status required under §63.999(b). The same data specified in this section shall be submitted in the reports of all subsequently required performance tests where either the emission control efficiency of a combustion device, or the outlet concentration of TOC or regulated material is determined.

Monitoring Frequency: AS REQUIRED - SEE PERMIT MONITORING DESCRIPTION

Reporting Requirements: AS REQUIRED - SEE MONITORING DESCRIPTION

Condition 258: Compliance Certification
Effective between the dates of 05/10/2008 and Permit Expiration Date

Applicable Federal Requirement:40CFR 63.998(a)(2), Subpart SS

Expired by Mod 1

Item 258.1:

The Compliance Certification activity will be performed for the facility:

The Compliance Certification applies to:

Emission Unit: C-27018
Process: 085

Emission Unit: C-27018
Process: 033

Emission Unit: C-27018
Process: 035

Emission Unit: C-27018
Process: 078

Emission Unit: C-27018
Process: 080

Emission Unit: C-27018
Process: 090

Emission Unit: C-27018
Process: 093



Emission Unit: C-27018
Process: 119

Emission Unit: C-27018
Process: 143

Emission Unit: C-27035
Process: 056

Emission Unit: F-INISH
Process: 069

Emission Unit: F-INISH
Process: 081

Emission Unit: F-INISH
Process: 169

Regulated Contaminant(s):
CAS No: 0NY100-00-0 HAP

Item 258.2:

Compliance Certification shall include the following monitoring:

Monitoring Type: RECORD KEEPING/MAINTENANCE PROCEDURES

Monitoring Description:

(C) Other nonflare control devices. Where an owner or operator seeks to use an absorber, condenser, or carbon adsorber as a control device, the information specified in paragraphs (a)(2)(ii)(C)(1) through (5) of this section shall be recorded, as applicable.

(1) Where an absorber is used as the control device, the exit specific gravity and average exit temperature of the absorbing liquid averaged over the same time period as the performance test (both measured while the vent stream is normally routed and constituted); or

(2)

(3)

(4) As an alternative to paragraph (a)(2)(ii)(C)(1), (2), or (3) of this section, the concentration level or reading indicated by an organics monitoring device at the outlet of the absorber, condenser, or carbon adsorber averaged over the same time period as the performance test while the vent stream is normally routed and constituted.

(5) For an absorber, condenser, or carbon adsorber used as a control device, the percent reduction of regulated material achieved by the control device or concentration of regulated material (parts per million by volume, by compound) at the outlet of the control device.

Monitoring Frequency: AS REQUIRED - SEE PERMIT MONITORING DESCRIPTION

Reporting Requirements: AS REQUIRED - SEE MONITORING DESCRIPTION



Condition 264: Compliance Certification
Effective between the dates of 05/10/2008 and Permit Expiration Date

Applicable Federal Requirement: 40CFR 63.998(c)(3), Subpart SS

Expired by Mod 1

Item 264.1:

The Compliance Certification activity will be performed for the facility:
The Compliance Certification applies to:

Emission Unit: C-27018
Process: 090

Emission Unit: F-INISH
Process: 069

Emission Unit: F-INISH
Process: 081

Emission Unit: F-INISH
Process: 169

Regulated Contaminant(s):
CAS No: 0NY100-00-0 HAP

Item 264.2:

Compliance Certification shall include the following monitoring:

Monitoring Type: RECORD KEEPING/MAINTENANCE PROCEDURES

Monitoring Description:

- (i) Each owner or operator using a recovery device to achieve and maintain a TRE index value greater than the control applicability level specified in the referencing subpart but less than 4.0 or using an absorber, condenser, carbon adsorber or other non-combustion system as a control device shall keep readily accessible, continuous records of the equipment operating parameters specified to be monitored under §§63.990(c) (absorber, condenser, and carbon adsorber monitoring), 63.993(c) (recovery device monitoring), or 63.995(c) (other noncombustion systems used as a control device monitoring) or as approved by the Administrator in accordance with a referencing subpart. For transfer racks, continuous records are required while the transfer vent stream is being vented.
- (ii) Each owner or operator shall keep records of the daily average value of each continuously monitored parameter for each operating day determined according to the procedures specified in paragraph (b)(3)(i) of this section.
- (iii) Each owner or operator subject to the provisions of this subpart shall keep up-to-date, readily accessible records of periods of operation during which the parameter



boundaries are exceeded. The parameter boundaries are established pursuant to §63.996(c)(6).

Monitoring Frequency: AS REQUIRED - SEE PERMIT MONITORING DESCRIPTION

Reporting Requirements: AS REQUIRED - SEE MONITORING DESCRIPTION

Condition 1-28: Compliance Certification
Effective between the dates of Permit Effective Date and 10/14/2008

Applicable Federal Requirement: 40CFR 63.1203(a)(5)(i), Subpart EEE

Item 1-28.1:

The Compliance Certification activity will be performed for the facility:
The Compliance Certification applies to:

Emission Unit: C-27018
Process: 422

Emission Unit: C-27018
Process: 423

Emission Unit: C-27018
Process: 424

Emission Unit: C-27018
Process: 425

Regulated Contaminant(s):
CAS No: 000630-08-0 CARBON MONOXIDE

Item 1-28.2:

Compliance Certification shall include the following monitoring:

Monitoring Type: CONTINUOUS EMISSION MONITORING (CEM)

Monitoring Description:

You must not discharge or cause combustion gases to be emitted into the atmosphere that contain either carbon monoxide in excess of 100 parts per million by volume, over an hourly rolling average (monitored continuously with a continuous emissions monitoring system), dry basis and corrected to 7 percent oxygen, or hydrocarbons in excess of 10 parts per million by volume, over an hourly rolling average (monitored continuously with a continuous emissions monitoring system), dry basis, corrected to 7 percent oxygen, and reported as propane as per paragraph (b)(5)(ii) of this section. If you elect to comply with this carbon monoxide standard rather than the hydrocarbon standard, you must also document that, during the destruction and removal efficiency (DRE) test runs or their equivalent as provided by §63.1206(b)(7), hydrocarbons do not exceed 10 parts per million by volume during those runs, over an hourly rolling average



(monitored continuously with a continuous emissions monitoring system), dry basis, corrected to 7 percent oxygen, and reported as propane; or hydrocarbons in excess of 10 parts per million by volume, over an hourly rolling average (monitored continuously with a continuous emissions monitoring system), dry basis, corrected to 7 percent oxygen, and reported as propane.

Manufacturer Name/Model Number: Servomex Xentra

Upper Permit Limit: 100 parts per million by volume
(dry, corrected to 7% O₂)

Reference Test Method: 40 CFR 60

Monitoring Frequency: CONTINUOUS

Averaging Method: 1 HOUR ROLLING AVERAGE ROLLED EVERY 1
MINUTE

Reporting Requirements: SEMI-ANNUALLY (CALENDAR)

Reports due 30 days after the reporting period.

Subsequent reports are due every 6 calendar month(s).

Condition 307: Compliance Certification
Effective between the dates of 01/07/2008 and Permit Expiration Date

Applicable Federal Requirement: 40CFR 63.1203(a)(5)(i), Subpart EEE

Expired by Mod 1

Item 307.1:

The Compliance Certification activity will be performed for the facility:

The Compliance Certification applies to:

Emission Unit: C-27018

Process: 422

Emission Unit: C-27018

Process: 423

Emission Unit: C-27018

Process: 424

Emission Unit: C-27018

Process: 425

Regulated Contaminant(s):

CAS No: 000630-08-0 CARBON MONOXIDE

Item 307.2:

Compliance Certification shall include the following monitoring:

Monitoring Type: CONTINUOUS EMISSION MONITORING (CEM)

Monitoring Description:

You must not discharge or cause combustion gases to be emitted into the atmosphere that contain either carbon monoxide in excess of 100 parts per million by volume, over an hourly rolling average (monitored continuously



with a continuous emissions monitoring system), dry basis and corrected to 7 percent oxygen, or hydrocarbons in excess of 10 parts per million by volume, over an hourly rolling average (monitored continuously with a continuous emissions monitoring system), dry basis, corrected to 7 percent oxygen, and reported as propane as per paragraph (b)(5)(ii) of this section. If you elect to comply with this carbon monoxide standard rather than the hydrocarbon standard, you must also document that, during the destruction and removal efficiency (DRE) test runs or their equivalent as provided by §63.1206(b)(7), hydrocarbons do not exceed 10 parts per million by volume during those runs, over an hourly rolling average (monitored continuously with a continuous emissions monitoring system), dry basis, corrected to 7 percent oxygen, and reported as propane; or hydrocarbons in excess of 10 parts per million by volume, over an hourly rolling average (monitored continuously with a continuous emissions monitoring system), dry basis, corrected to 7 percent oxygen, and reported as propane.

Manufacturer Name/Model Number: Servomex Xentra

Upper Permit Limit: 100 parts per million by volume
(dry, corrected to 7% O₂)

Reference Test Method: 40 CFR 60

Monitoring Frequency: CONTINUOUS

Averaging Method: 1 HOUR ROLLING AVERAGE ROLLED EVERY 1
MINUTE

Reporting Requirements: SEMI-ANNUALLY (CALENDAR)

Reports due 30 days after the reporting period.

The initial report is due 7/30/2008.

Subsequent reports are due every 6 calendar month(s).

Condition 1-29: Compliance Certification
Effective for entire length of Permit

Applicable Federal Requirement: 40CFR 63.1206(c), Subpart EEE

Item 1-29.1:

The Compliance Certification activity will be performed for the facility:

The Compliance Certification applies to:

Emission Unit: C-27018
Process: 422

Emission Unit: C-27018
Process: 423

Emission Unit: C-27018
Process: 424

Emission Unit: C-27018
Process: 425



Item 1-29.2:

Compliance Certification shall include the following monitoring:

Monitoring Type: RECORD KEEPING/MAINTENANCE PROCEDURES

Monitoring Description:

You must operate only under the operating requirements specified in the Documentation of Compliance under §63.1211(c) or the Notification of Compliance under §§63.1207(j) and 63.1210(d), except during performance tests under approved test plans according to §63.1207(e), (f), and (g), and under the conditions of paragraph (b)(1)(i) or (ii) of this section.

Monitoring Frequency: AS REQUIRED - SEE PERMIT MONITORING DESCRIPTION

Reporting Requirements: AS REQUIRED - SEE MONITORING DESCRIPTION

Condition 314: Compliance Certification
Effective between the dates of 01/07/2008 and Permit Expiration Date

Applicable Federal Requirement:40CFR 63.1206(c), Subpart EEE

Expired by Mod 1

Item 314.1:

The Compliance Certification activity will be performed for the facility:

The Compliance Certification applies to:

Emission Unit: C-27018
Process: 422

Emission Unit: C-27018
Process: 423

Emission Unit: C-27018
Process: 424

Emission Unit: C-27018
Process: 425

Item 314.2:

Compliance Certification shall include the following monitoring:

Monitoring Type: RECORD KEEPING/MAINTENANCE PROCEDURES

Monitoring Description:

You must operate only under the operating requirements specified in the Documentation of Compliance under §63.1211(c) or the Notification of Compliance under §§63.1207(j) and 63.1210(d), except during performance tests under approved test plans according to §63.1207(e), (f), and (g), and under the conditions of paragraph (b)(1)(i) or (ii) of this section.



Monitoring Frequency: AS REQUIRED - SEE PERMIT MONITORING DESCRIPTION

Reporting Requirements: AS REQUIRED - SEE MONITORING DESCRIPTION

Condition 316: Compliance Certification
Effective between the dates of 01/07/2008 and Permit Expiration Date

Applicable Federal Requirement:40CFR 63.1207, Subpart EEE

Expired by Mod 1

Item 316.1:

The Compliance Certification activity will be performed for the facility:
The Compliance Certification applies to:

Emission Unit: C-27018	Emission Point: 97001
Emission Unit: C-27018	Emission Point: 97002
Emission Unit: C-27018	Emission Point: 97003

Item 316.2:

Compliance Certification shall include the following monitoring:

Monitoring Type: RECORD KEEPING/MAINTENANCE PROCEDURES

Monitoring Description:

Comprehensive performance test (cpt)

The permittee must conduct comprehensive performance tests (cpt) to demonstrate compliance with the emission standards in this subpart , establish operating limits for operating parameters, and demonstrate compliance with the performance specifications for continuous monitoring systems (CMS).

The permittee must conduct initial comprehensive performance tests (cpt) by March 30, 2003.

The subsequent cpt must commence no later than 61 (Sixty-one) months after the date of commencing the previous cpt. (3/25/04 for the RKI and 4/4/04 for the FBI)

The cpt must be completed within the 60 (Sixty) days after the date of commencement.

The permittee must submit to the NYSDEC a notification of intention to conduct a cpt, CMS performance evaluation, a site specific test plan, and CMS performance evaluation plan at least one year before the cpt and CMS performance evaluations are scheduled to begin.

The NYSDEC will notify the permittee of approval or intent to deny approval of the test plan and CMS performance



evaluation plan within 9 (Nine) months after receipt of the original plan.

The permittee must submit to the NYSDEC a notification of intention to conduct the cpt at least 60 (Sixty) calendar days before the test is scheduled to begin.

Confirmatory performance test (ct)

The permittee must conduct confirmatory performance tests (ct) to demonstrate compliance with the dioxin/furan emission standards in this subpart, under normal conditions.

The subsequent ct must commence no earlier than 18 months and no later than 31 (Thirty-one) months after the date of commencing the previous cpt.

The ct must be completed within the 60 (Sixty) days after the date of commencement.

The permittee must submit to the NYSDEC a notification of intention to conduct the ct at least 60 (Sixty) calendar days before the test is scheduled to begin.

The NYSDEC will notify the permittee of approval or intent to deny approval of the test plan and CMS performance evaluation plan within 30 (Thirty) calendar days after receipt of the original plans.

Monitoring Frequency: AS REQUIRED - SEE PERMIT MONITORING DESCRIPTION

Reporting Requirements: AS REQUIRED - SEE MONITORING DESCRIPTION

**Condition 1-30: Compliance Certification
Effective for entire length of Permit**

Applicable Federal Requirement: 40CFR 63.1209(j)(2), Subpart EEE

Item 1-30.1:

The Compliance Certification activity will be performed for the facility:
The Compliance Certification applies to:

Emission Unit: C-27018

Emission Point: 97001

Item 1-30.2:

Compliance Certification shall include the following monitoring:

Monitoring Type: MONITORING OF PROCESS OR CONTROL
DEVICE PARAMETERS AS SURROGATE

Monitoring Description:



As an indicator of gas residence time in the control device, you must establish and comply with a limit on the maximum flue gas flowrate, the maximum production rate, or another parameter that you document in the site-specific test plan as an appropriate surrogate for gas residence time, as the average of the maximum hourly rolling averages for each run and you must comply with this limit on a hourly rolling average basis.

If the monitored parameter exceeds the limitation, the automatic waste feed cutoff must immediately and automatically cut off of the hazardous waste feed, except as provided by Section 63.1206(c)(3)(viii). In accordance with 63.1206(c)(2)(v)(2), an exceedance of this emission standard is not a violation of 40 CFR Part 63, Subpart EEE if you take the corrective measures prescribed in the startup, shutdown, and malfunction plan.

The flue gas flow rate of the Fixed Box Incinerator #1 stack will be monitored continuously and will be limited to a maximum of 4,583 acfm on an hourly rolling average basis.

This condition also satisfies the following requirements:

- ι 40 CFR 63.1209(k)(3), dioxins and furans ι maximum flue gas flowrate or production rate
- ι 40 CFR 63.1209(m)(2), particulate matter ι maximum flue gas flow rate or production rate
- ι 40 CFR 63.1209(n)(5), semivolatile metals and low volatility metals - maximum flue gas flow rate or production rate
- ι 40 CFR 63.1209(o)(3)(v), hydrogen chloride and chlorine gas ι wet scrubber

Parameter Monitored: VOLUMETRIC FLOW RATE

Upper Permit Limit: 4583 cubic feet per minute

Monitoring Frequency: CONTINUOUS

Averaging Method: 1 HOUR ROLLING AVERAGE ROLLED EVERY 1 MINUTE

Reporting Requirements: SEMI-ANNUALLY (CALENDAR)

Reports due 30 days after the reporting period.

Subsequent reports are due every 6 calendar month(s).

Condition 1-31: Compliance Certification
Effective for entire length of Permit

Applicable Federal Requirement: 40CFR 63.1209(j)(2), Subpart EEE

Item 1-31.1:

The Compliance Certification activity will be performed for the facility:

The Compliance Certification applies to:



Emission Unit: C-27018

Emission Point: 97002

Item 1-31.2:

Compliance Certification shall include the following monitoring:

Monitoring Type: MONITORING OF PROCESS OR CONTROL
DEVICE PARAMETERS AS SURROGATE

Monitoring Description:

As an indicator of gas residence time in the control device, you must establish and comply with a limit on the maximum flue gas flowrate, the maximum production rate, or another parameter that you document in the site-specific test plan as an appropriate surrogate for gas residence time, as the average of the maximum hourly rolling averages for each run and you must comply with this limit on a hourly rolling average basis.

If the monitored parameter exceeds the limitation, the automatic waste feed cutoff must immediately and automatically cut off of the hazardous waste feed, except as provided by Section 63.1206(c)(3)(viii). In accordance with 63.1206(c)(2)(v)(2), an exceedance of this emission standard is not a violation of 40 CFR Part 63, Subpart EEE if you take the corrective measures prescribed in the startup, shutdown, and malfunction plan.

Flue gas flow rate will be monitored continuously and will be limited to a maximum of 4,750 acfm on an hourly rolling average basis. This condition also satisfies the following requirements:

- ∩ 40 CFR 63.1209(k)(3) Dioxins and furans ∩ maximum flue gas flowrate or production rate
- ∩ 40 CFR 63.1209(k)(3) Dioxins and furans ∩ maximum flue gas flowrate or production rate
- ∩ 40 CFR 63.1209(n)(5) Semivolatile metals and low volatility metals - maximum flue gas flow rate or production rate
- ∩ 40 CFR 63.1209(o)(3)(v), hydrogen chloride and chlorine gas ∩ wet scrubber

Parameter Monitored: VOLUMETRIC FLOW RATE

Upper Permit Limit: 4750 cubic feet per minute

Monitoring Frequency: CONTINUOUS

Averaging Method: 1 HOUR ROLLING AVERAGE ROLLED EVERY 1
MINUTE

Reporting Requirements: SEMI-ANNUALLY (CALENDAR)

Reports due 30 days after the reporting period.

Subsequent reports are due every 6 calendar month(s).

Condition 1-32: Compliance Certification
Effective for entire length of Permit

Applicable Federal Requirement: 40CFR 63.1209(j)(2), Subpart EEE



Item 1-32.1:

The Compliance Certification activity will be performed for the facility:

The Compliance Certification applies to:

Emission Unit: C-27018

Emission Point: 97003

Item 1-32.2:

Compliance Certification shall include the following monitoring:

Monitoring Type: MONITORING OF PROCESS OR CONTROL
DEVICE PARAMETERS AS SURROGATE

Monitoring Description:

As an indicator of gas residence time in the control device, you must establish and comply with a limit on the maximum flue gas flowrate, the maximum production rate, or another parameter that you document in the site-specific test plan as an appropriate surrogate for gas residence time, as the average of the maximum hourly rolling averages for each run and you must comply with this limit on a hourly rolling average basis.

If the monitored parameter exceeds the limitation, the automatic waste feed cutoff must immediately and automatically cut off of the hazardous waste feed, except as provided by Section 63.1206(c)(3)(viii). In accordance with 63.1206(c)(2)(v)(2), an exceedance of this emission standard is not a violation of 40 CFR Part 63, Subpart EEE if you take the corrective measures prescribed in the startup, shutdown, and malfunction plan.

The flue gas flow rate of the RKI will be monitored continuously and will be limited to a maximum of 16,361 acfm on an hourly rolling average basis. This condition also satisfies the requirements of:

- ζ 40 CFR 63.1209(k)(3), dioxins and furans ζ maximum flue gas flowrate or production rate
- ζ 40 CFR 63.1209(m)(2), particulate matter ζ maximum flue gas flow rate or production rate
- ζ 40 CFR 63.1209(n)(5), semivolatile metals and low volatility metals - maximum flue gas flow rate or production rate
- ζ 40 CFR 63.1209(o)(3)(v), hydrogen chloride and chlorine gas ζ wet scrubber

Parameter Monitored: VOLUMETRIC FLOW RATE

Upper Permit Limit: 16361 cubic feet per minute

Monitoring Frequency: CONTINUOUS

Averaging Method: 1 HOUR ROLLING AVERAGE ROLLED EVERY 1
MINUTE

Reporting Requirements: SEMI-ANNUALLY (CALENDAR)

Reports due 30 days after the reporting period.

Subsequent reports are due every 6 calendar month(s).



Condition 1-33: Compliance Certification
Effective for entire length of Permit

Applicable Federal Requirement: 40CFR 63.1209(j)(2), Subpart EEE

Item 1-33.1:

The Compliance Certification activity will be performed for the facility:
The Compliance Certification applies to:

Emission Unit: C-27018
Process: 423

Item 1-33.2:

Compliance Certification shall include the following monitoring:

Monitoring Type: MONITORING OF PROCESS OR CONTROL
DEVICE PARAMETERS AS SURROGATE

Monitoring Description:

As an indicator of gas residence time in the control device, you must establish and comply with a limit on the maximum flue gas flowrate, the maximum production rate, or another parameter that you document in the site-specific test plan as an appropriate surrogate for gas residence time, as the average of the maximum hourly rolling averages for each run and you must comply with this limit on a hourly rolling average basis.

If the monitored parameter exceeds the limitation, the automatic waste feed cutoff must immediately and automatically cut off of the hazardous waste feed, except as provided by Section 63.1206(c)(3)(viii). In accordance with 63.1206(c)(2)(v)(2), an exceedance of this emission standard is not a violation of 40 CFR Part 63, Subpart EEE if you take the corrective measures prescribed in the startup, shutdown, and malfunction plan.

Flue gas flow rate will be monitored continuously and will be maintained at a maximum of 10,460 acfm on an hourly rolling average basis. This condition also satisfies the following requirements:

- ∩ 40 CFR 63.1209(n)(5), Semivolatile metals and low volatility metals - maximum flue gas flow rate or production rate
- ∩ 40 CFR 63.1209(k)(3), Dioxins and furans ∩ maximum flue gas flowrate or production rate
- ∩ 40 CFR 63.1209(m)(2), Particulate matter ∩ maximum flue gas flow rate or production rate
- ∩ 40 CFR 63.1209(o)(3)(v), hydrogen chloride and chlorine gas ∩ wet scrubber

Parameter Monitored: VOLUMETRIC FLOW RATE
Upper Permit Limit: 10460 cubic feet per minute



Monitoring Frequency: CONTINUOUS
Averaging Method: 1 HOUR ROLLING AVERAGE ROLLED EVERY 1
MINUTE
Reporting Requirements: SEMI-ANNUALLY (CALENDAR)
Reports due 30 days after the reporting period.
Subsequent reports are due every 6 calendar month(s).

Condition 1-34: Compliance Certification
Effective for entire length of Permit

Applicable Federal Requirement: 40CFR 63.1209(j)(2), Subpart EEE

Item 1-34.1:

The Compliance Certification activity will be performed for the facility:
The Compliance Certification applies to:

Emission Unit: C-27018
Process: 425

Item 1-34.2:

Compliance Certification shall include the following monitoring:

Monitoring Type: MONITORING OF PROCESS OR CONTROL
DEVICE PARAMETERS AS SURROGATE

Monitoring Description:

As an indicator of gas residence time in the control device, you must establish and comply with a limit on the maximum flue gas flowrate, the maximum production rate, or another parameter that you document in the site-specific test plan as an appropriate surrogate for gas residence time, as the average of the maximum hourly rolling averages for each run and you must comply with this limit on a hourly rolling average basis.

If the monitored parameter exceeds the limitation, the automatic waste feed cutoff must immediately and automatically cut off of the hazardous waste feed, except as provided by Section 63.1206(c)(3)(viii). In accordance with 63.1206(c)(2)(v)(2), an exceedance of this emission standard is not a violation of 40 CFR Part 63, Subpart EEE if you take the corrective measures prescribed in the startup, shutdown, and malfunction plan.

Flue gas flow rate will be monitored continuously and will be limited to 6,736 acfm on an hourly rolling average basis. This condition also satisfies the following requirements:

- ∩ 40 CFR 63.1209(k)(3) Dioxins and furans ∩ maximum flue gas flowrate or production rate
- ∩ 40 CFR 63.1209(m)(2) Particulate matter ∩ maximum flue gas flow rate or production rate
- ∩ 40 CFR 63.1209(n)(5) Semivolatile metals and low volatility metals - maximum flue gas flow rate or



production rate 40 CFR 63.1209(o)(3)(v), hydrogen chloride and chlorine gas, wet scrubber

Parameter Monitored: VOLUMETRIC FLOW RATE

Upper Permit Limit: 6736 cubic feet per minute

Monitoring Frequency: CONTINUOUS

Averaging Method: 1 HOUR ROLLING AVERAGE ROLLED EVERY 1 MINUTE

Reporting Requirements: SEMI-ANNUALLY (CALENDAR)

Reports due 30 days after the reporting period.

Subsequent reports are due every 6 calendar month(s).

Condition 331: Compliance Certification
Effective between the dates of 01/07/2008 and Permit Expiration Date

Applicable Federal Requirement: 40 CFR 63.1209(j)(2), Subpart EEE

Expired by Mod 1

Item 331.1:

The Compliance Certification activity will be performed for the facility:

The Compliance Certification applies to:

Emission Unit: C-27018

Emission Point: 97001

Item 331.2:

Compliance Certification shall include the following monitoring:

Monitoring Type: MONITORING OF PROCESS OR CONTROL DEVICE PARAMETERS AS SURROGATE

Monitoring Description:

As an indicator of gas residence time in the control device, you must establish and comply with a limit on the maximum flue gas flowrate, the maximum production rate, or another parameter that you document in the site-specific test plan as an appropriate surrogate for gas residence time, as the average of the maximum hourly rolling averages for each run and you must comply with this limit on a hourly rolling average basis.

If the monitored parameter exceeds the limitation, the automatic waste feed cutoff must immediately and automatically cut off of the hazardous waste feed, except as provided by Section 63.1206(c)(3)(viii). In accordance with 63.1206(c)(2)(v)(2), an exceedance of this emission standard is not a violation of 40 CFR Part 63, Subpart EEE if you take the corrective measures prescribed in the startup, shutdown, and malfunction plan.

The flue gas flow rate of the Fixed Box Incinerator #1 stack will be monitored continuously and will be limited to a maximum of 4,583 acfm on an hourly rolling average basis.



This condition also satisfies the following requirements:

- 40 CFR 63.1209(k)(3), dioxins and furans
- maximum flue gas flowrate or production rate
- 40 CFR 63.1209(m)(2), particulate matter
- maximum flue gas flow rate or production rate
- 40 CFR 63.1209(n)(5), semivolatile metals and low volatility metals - maximum flue gas flow rate or production rate
- 40 CFR 63.1209(o)(3)(v), hydrogen chloride and chlorine gas
- wet scrubber

Parameter Monitored: VOLUMETRIC FLOW RATE

Upper Permit Limit: 4583 cubic feet per minute

Monitoring Frequency: CONTINUOUS

Averaging Method: 1 HOUR ROLLING AVERAGE ROLLED EVERY 1 MINUTE

Reporting Requirements: SEMI-ANNUALLY (CALENDAR)

Reports due 30 days after the reporting period.

The initial report is due 7/30/2008.

Subsequent reports are due every 6 calendar month(s).

Condition 334: Compliance Certification
Effective between the dates of 01/07/2008 and Permit Expiration Date

Applicable Federal Requirement: 40CFR 63.1209(j)(2), Subpart EEE

Expired by Mod 1

Item 334.1:

The Compliance Certification activity will be performed for the facility:

The Compliance Certification applies to:

Emission Unit: C-27018

Emission Point: 97002

Item 334.2:

Compliance Certification shall include the following monitoring:

Monitoring Type: MONITORING OF PROCESS OR CONTROL DEVICE PARAMETERS AS SURROGATE

Monitoring Description:

As an indicator of gas residence time in the control device, you must establish and comply with a limit on the maximum flue gas flowrate, the maximum production rate, or another parameter that you document in the site-specific test plan as an appropriate surrogate for gas residence time, as the average of the maximum hourly rolling averages for each run and you must comply with this limit on a hourly rolling average basis.

If the monitored parameter exceeds the limitation, the automatic waste feed cutoff must immediately and automatically cut off of the hazardous waste feed, except as provided by Section 63.1206(c)(3)(viii). In accordance



with 63.1206(c)(2)(v)(2), an exceedance of this emission standard is not a violation of 40 CFR Part 63, Subpart EEE if you take the corrective measures prescribed in the startup, shutdown, and malfunction plan.

Flue gas flow rate will be monitored continuously and will be limited to a maximum of 4,750 acfm on an hourly rolling average basis. This condition also satisfies the following requirements:

- ζ 40 CFR 63.1209(k)(3) Dioxins and furans ζ maximum flue gas flowrate or production rate
- ζ 40 CFR 63.1209(k)(3) Dioxins and furans ζ maximum flue gas flowrate or production rate
- ζ 40 CFR 63.1209(n)(5) Semivolatile metals and low volatility metals - maximum flue gas flow rate or production rate
- ζ 40 CFR 63.1209(o)(3)(v), hydrogen chloride and chlorine gas ζ wet scrubber

Parameter Monitored: VOLUMETRIC FLOW RATE

Upper Permit Limit: 4750 cubic feet per minute

Monitoring Frequency: CONTINUOUS

Averaging Method: 1 HOUR ROLLING AVERAGE ROLLED EVERY 1 MINUTE

Reporting Requirements: SEMI-ANNUALLY (CALENDAR)

Reports due 30 days after the reporting period.

The initial report is due 7/30/2008.

Subsequent reports are due every 6 calendar month(s).

Condition 1-35: Compliance Certification
Effective for entire length of Permit

Applicable Federal Requirement: 40 CFR 63.1209(j)(3), Subpart EEE

Item 1-35.1:

The Compliance Certification activity will be performed for the facility:

The Compliance Certification applies to:

Emission Unit: C-27018

Process: 422

Emission Unit: C-27018

Process: 423

Item 1-35.2:

Compliance Certification shall include the following monitoring:

Monitoring Type: MONITORING OF PROCESS OR CONTROL DEVICE PARAMETERS AS SURROGATE

Monitoring Description:

You must establish limits on the maximum pumpable and total (i.e., pumpable and nonpumpable) hazardous waste feedrate for each location where hazardous waste is fed,



you must establish the limits as the average of the maximum hourly rolling averages for each run, and you must comply with the feedrate limit(s) on a hourly rolling average basis.

If the monitored parameter exceeds the limitation, the automatic waste feed cutoff must immediately and automatically cut off of the hazardous waste feed, except as provided by Section 63.1206(c)(3)(viii). In accordance with 63.1206(c)(2)(v)(2), an exceedance of this emission standard is not a violation of 40 CFR Part 63, Subpart EEE if you take the corrective measures prescribed in the startup, shutdown, and malfunction plan.

The total hazardous waste drum feed rate will be monitored continuously and will be limited to a maximum of 751 pounds per hour on an hourly rolling average basis. This condition also satisfies the requirements of 40 CFR 63.1209(k)(4), dioxins and furans ζ maximum hazardous waste federate.

Parameter Monitored: WASTE MATERIAL

Upper Permit Limit: 751 pounds per hour

Monitoring Frequency: CONTINUOUS

Averaging Method: 1 HOUR MAXIMUM - NOT TO BE EXCEEDED AT ANY TIME

Reporting Requirements: SEMI-ANNUALLY (CALENDAR)

Reports due 30 days after the reporting period.

Subsequent reports are due every 6 calendar month(s).

Condition 336: Compliance Certification

Effective between the dates of 01/07/2008 and Permit Expiration Date

Applicable Federal Requirement:40CFR 63.1209(j)(3), Subpart EEE

Expired by Mod 1

Item 336.1:

The Compliance Certification activity will be performed for the facility:

The Compliance Certification applies to:

Emission Unit: C-27018

Process: 422

Emission Unit: C-27018

Process: 423

Item 336.2:

Compliance Certification shall include the following monitoring:

Monitoring Type: MONITORING OF PROCESS OR CONTROL
DEVICE PARAMETERS AS SURROGATE

Monitoring Description:

You must establish limits on the maximum pumpable and



total (i.e., pumpable and nonpumpable) hazardous waste feedrate for each location where hazardous waste is fed, you must establish the limits as the average of the maximum hourly rolling averages for each run, and you must comply with the feedrate limit(s) on a hourly rolling average basis.

If the monitored parameter exceeds the limitation, the automatic waste feed cutoff must immediately and automatically cut off of the hazardous waste feed, except as provided by Section 63.1206(c)(3)(viii). In accordance with 63.1206(c)(2)(v)(2), an exceedance of this emission standard is not a violation of 40 CFR Part 63, Subpart EEE if you take the corrective measures prescribed in the startup, shutdown, and malfunction plan.

The total hazardous waste feed rate will be monitored continuously and will be limited to a maximum of 751 pounds per hour on an hourly rolling average basis. This condition also satisfies the requirements of 40 CFR 63.1209(k)(4), dioxins and furans ζ maximum hazardous waste feedrate.

Parameter Monitored: WASTE MATERIAL

Upper Permit Limit: 751 pounds per hour

Monitoring Frequency: CONTINUOUS

Averaging Method: 1 HOUR MAXIMUM - NOT TO BE EXCEEDED AT ANY TIME

Reporting Requirements: SEMI-ANNUALLY (CALENDAR)

Reports due 30 days after the reporting period.

The initial report is due 7/30/2008.

Subsequent reports are due every 6 calendar month(s).

**Condition 1-36: Compliance Certification
Effective for entire length of Permit**

Applicable Federal Requirement: 40CFR 63.1209(j)(4), Subpart EEE

Item 1-36.1:

The Compliance Certification activity will be performed for the facility:

The Compliance Certification applies to:

Emission Unit: C-27018

Process: 424

Emission Unit: C-27018

Process: 425

Item 1-36.2:

Compliance Certification shall include the following monitoring:

Monitoring Type: MONITORING OF PROCESS OR CONTROL
DEVICE PARAMETERS AS SURROGATE



Monitoring Description:

You must specify operating parameters and limits to ensure that good operation of each hazardous waste firing system is maintained.

If the monitored parameter exceeds the limitation, the automatic waste feed cutoff must immediately and automatically cut off of the hazardous waste feed, except as provided by Section 63.1206(c)(3)(viii). In accordance with 63.1206(c)(2)(v)(2), an exceedance of this emission standard is not a violation of 40 CFR Part 63, Subpart EEE if you take the corrective measures prescribed in the startup, shutdown, and malfunction plan.

Air atomization pressure will be maintained at a minimum of 80.6 psig and will be monitored continuously on an hourly rolling average basis.

Parameter Monitored: PRESSURE

Lower Permit Limit: 80.6 pounds per square inch gauge

Monitoring Frequency: CONTINUOUS

Averaging Method: 1-HOUR AVERAGE

Reporting Requirements: SEMI-ANNUALLY (CALENDAR)

Reports due 30 days after the reporting period.

Subsequent reports are due every 6 calendar month(s).

**Condition 1-37: Compliance Certification
Effective for entire length of Permit**

Applicable Federal Requirement: 40CFR 63.1209(j)(4), Subpart EEE

Item 1-37.1:

The Compliance Certification activity will be performed for the facility:

The Compliance Certification applies to:

Emission Unit: C-27018

Process: 422

Emission Unit: C-27018

Process: 423

Item 1-37.2:

Compliance Certification shall include the following monitoring:

Monitoring Type: MONITORING OF PROCESS OR CONTROL
DEVICE PARAMETERS AS SURROGATE

Monitoring Description:

You must specify operating parameters and limits to ensure that good operation of each hazardous waste firing system is maintained.

If the monitored parameter exceeds the limitation, the automatic waste feed cutoff must immediately and



automatically cut off of the hazardous waste feed, except as provided by Section 63.1206(c)(3)(viii). In accordance with 63.1206(c)(2)(v)(2), an exceedance of this emission standard is not a violation of 40 CFR Part 63, Subpart EEE if you take the corrective measures prescribed in the startup, shutdown, and malfunction plan.

Steam atomization pressure is monitored continuously and will be maintained at a minimum of 126 psig on an hourly rolling average basis.

Parameter Monitored: STEAM

Lower Permit Limit: 126 pounds per square inch gauge

Monitoring Frequency: CONTINUOUS

Averaging Method: 1 HOUR ROLLING AVERAGE ROLLED EVERY 1 MINUTE

Reporting Requirements: SEMI-ANNUALLY (CALENDAR)

Reports due 30 days after the reporting period.

Subsequent reports are due every 6 calendar month(s).

**Condition 1-38: Compliance Certification
Effective for entire length of Permit**

Applicable Federal Requirement: 40CFR 63.1209(j)(4), Subpart EEE

Item 1-38.1:

The Compliance Certification activity will be performed for the facility:

The Compliance Certification applies to:

Emission Unit: C-27018

Process: 422

Emission Unit: C-27018

Process: 423

Item 1-38.2:

Compliance Certification shall include the following monitoring:

Monitoring Type: MONITORING OF PROCESS OR CONTROL DEVICE PARAMETERS AS SURROGATE

Monitoring Description:

You must specify operating parameters and limits to ensure that good operation of each hazardous waste firing system is maintained.

If the monitored parameter exceeds the limitation, the automatic waste feed cutoff must immediately and automatically cut off of the hazardous waste feed, except as provided by Section 63.1206(c)(3)(viii). In accordance with 63.1206(c)(2)(v)(2), an exceedance of this emission standard is not a violation of 40 CFR Part 63, Subpart EEE if you take the corrective measures prescribed in the startup, shutdown, and malfunction plan.



Parameter Monitored: STEAM FLOW RATE
Lower Permit Limit: 116 pounds per square inch gauge
Monitoring Frequency: CONTINUOUS
Averaging Method: 1-HOUR AVERAGE
Reporting Requirements: SEMI-ANNUALLY (CALENDAR)
Reports due 30 days after the reporting period.
The initial report is due 7/30/2008.
Subsequent reports are due every 6 calendar month(s).

Condition 1-39: Compliance Certification
Effective for entire length of Permit

Applicable Federal Requirement: 40CFR 63.1209(m)(1)(i)(B)'(1)',
Subpart EEE

Item 1-39.1:

The Compliance Certification activity will be performed for the facility:
The Compliance Certification applies to:

Emission Unit: C-27018 Process: 422	Emission Source: IWS1A
Emission Unit: C-27018 Process: 422	Emission Source: IWS1B
Emission Unit: C-27018 Process: 422	Emission Source: IWS1C
Emission Unit: C-27018 Process: 422	Emission Source: IWS2A
Emission Unit: C-27018 Process: 422	Emission Source: IWS2B
Emission Unit: C-27018 Process: 422	Emission Source: IWS2C
Emission Unit: C-27018 Process: 423	Emission Source: IWS1A
Emission Unit: C-27018 Process: 423	Emission Source: IWS1B
Emission Unit: C-27018 Process: 423	Emission Source: IWS1C
Emission Unit: C-27018 Process: 423	Emission Source: IWS2A
Emission Unit: C-27018 Process: 423	Emission Source: IWS2B
Emission Unit: C-27018	



Process: 423

Emission Source: IWS2C

Item 1-39.2:

Compliance Certification shall include the following monitoring:

Monitoring Type: MONITORING OF PROCESS OR CONTROL
DEVICE PARAMETERS AS SURROGATE

Monitoring Description:

For sources equipped with wet scrubbers, including ionizing wet scrubbers, high energy wet scrubbers such as venturi, hydrosonic, collision, or free jet wet scrubbers, and low energy wet scrubbers, you must establish limits to ensure that the solids content of the scrubber liquid does not exceed levels (established) during the performance test, by either (i) Establishing a limit on solids content of the scrubber liquid using a CMS or by manual sampling and analysis; or (ii) Establishing a minimum blowdown rate using a CMS and either a minimum scrubber tank volume or liquid level using a CMS. If you elect to monitor solids content manually, you must sample and analyze the scrubber liquid hourly unless you support an alternative monitoring frequency in the performance test plan that you submit for review and approval

If the monitored parameter exceeds the limitation, the automatic waste feed cutoff must immediately and automatically cut off of the hazardous waste feed, except as provided by Section 63.1206(c)(3)(viii). In accordance with 63.1206(c)(2)(v)(2), an exceedance of this emission standard is not a violation of 40 CFR Part 63, Subpart EEE if you take the corrective measures prescribed in the startup, shutdown, and malfunction plan.

The facility IWS system has a constant overflow sump instead of a recirculating tank system. Compliance with the requirement is achieved with a minimum IWS voltage of 17 kV (1-hour average) for each IWS unit IWS1A, IWS1B, IWS1C, IWS, IWS2A, IWS2B & IWS2C.

Parameter Monitored: VOLTAGE

Upper Permit Limit: 17 kilovolts

Monitoring Frequency: CONTINUOUS

Averaging Method: 1-HOUR AVERAGE

Reporting Requirements: SEMI-ANNUALLY (CALENDAR)

Reports due 30 days after the reporting period.

Subsequent reports are due every 6 calendar month(s).

Condition 353: Compliance Certification

Effective between the dates of 01/07/2008 and Permit Expiration Date

Applicable Federal Requirement: 40CFR 63.1209(m)(1)(i)('B')('1'),

Subpart EEE



Expired by Mod 1

Item 353.1:

The Compliance Certification activity will be performed for the facility:

The Compliance Certification applies to:

Emission Unit: C-27018 Process: 422	Emission Source: IWS1A
Emission Unit: C-27018 Process: 422	Emission Source: IWS1B
Emission Unit: C-27018 Process: 422	Emission Source: IWS2A
Emission Unit: C-27018 Process: 422	Emission Source: IWS2B
Emission Unit: C-27018 Process: 423	Emission Source: IWS1A
Emission Unit: C-27018 Process: 423	Emission Source: IWS1B
Emission Unit: C-27018 Process: 423	Emission Source: IWS2A
Emission Unit: C-27018 Process: 423	Emission Source: IWS2B
Emission Unit: C-27018 Process: 422	Emission Source: IWS1C
Emission Unit: C-27018 Process: 422	Emission Source: IWS2C
Emission Unit: C-27018 Process: 423	Emission Source: IWS1C
Emission Unit: C-27018 Process: 423	Emission Source: IWS2C

Item 353.2:

Compliance Certification shall include the following monitoring:

Monitoring Type: MONITORING OF PROCESS OR CONTROL
DEVICE PARAMETERS AS SURROGATE

Monitoring Description:

For sources equipped with wet scrubbers, including ionizing wet scrubbers, high energy wet scrubbers such as venturi, hydrosonic, collision, or free jet wet scrubbers, and low energy wet scrubbers, you must establish limits to ensure that the solids content of the scrubber liquid does not exceed levels (established) during the performance



Monitoring Type: MONITORING OF PROCESS OR CONTROL
DEVICE PARAMETERS AS SURROGATE

Monitoring Description:

If your source is equipped with a low energy wet scrubber, you must establish limits on either the minimum liquid to gas ratio or the minimum scrubber water flowrate and maximum flue gas flowrate on an hourly rolling average as the average of the test run averages. If you establish limits on maximum flue gas flowrate under this paragraph, you need not establish a limit on maximum flue gas flowrate under paragraph (o)(2) of this section.

If the monitored parameter exceeds the limitation, the automatic waste feed cutoff must immediately and automatically cut off of the hazardous waste feed, except as provided by Section 63.1206(c)(3)(viii). In accordance with 63.1206(c)(2)(v)(2), an exceedance of this emission standard is not a violation of 40 CFR Part 63, Subpart EEE if you take the corrective measures prescribed in the startup, shutdown, and malfunction plan.

Scrubber water flow rate will be monitored continuously and will be maintained at a minimum of 146 gallons per minute on an hourly rolling average basis.

Parameter Monitored: VOLUMETRIC FLOW RATE

Lower Permit Limit: 146 gallons per minute

Monitoring Frequency: CONTINUOUS

Averaging Method: 1 HOUR ROLLING AVERAGE ROLLED EVERY 1
MINUTE

Reporting Requirements: SEMI-ANNUALLY (CALENDAR)

Reports due 30 days after the reporting period.

The initial report is due 7/30/2008.

Subsequent reports are due every 6 calendar month(s).

Condition 1-27: Compliance Certification
Effective for entire length of Permit

Applicable Federal Requirement: 40CFR 63.1209(p), Subpart EEE

Item 1-27.1:

The Compliance Certification activity will be performed for the facility:

The Compliance Certification applies to:

Emission Unit: C-27018

Process: 422

Emission Source: 96RKI

Emission Unit: C-27018

Process: 423

Emission Source: 96RKI

Item 1-27.2:

Compliance Certification shall include the following monitoring:



Monitoring Type: MONITORING OF PROCESS OR CONTROL
DEVICE PARAMETERS AS SURROGATE

Monitoring Description:

If you comply with the requirements for combustion system leaks under §63.1206(c)(5) by maintaining the maximum combustion chamber zone pressure lower than ambient pressure to prevent combustion systems leaks from hazardous waste combustion, you must perform instantaneous monitoring of pressure and the automatic waste feed cutoff system must be engaged when negative pressure is not adequately maintained.

If the monitored parameter exceeds the limitation, the automatic waste feed cutoff must immediately and automatically cut off of the hazardous waste feed, except as provided by Section 63.1206(c)(3)(viii). In accordance with 63.1206(c)(2)(v)(2), an exceedance of this emission standard is not a violation of 40 CFR Part 63, Subpart EEE if you take the corrective measures prescribed in the startup, shutdown, and malfunction plan.

Combustion chamber zone pressure will be monitored continuously and will be maintained at a maximum of negative 0.3 inches of water at all times.

Parameter Monitored: PRESSURE

Upper Permit Limit: -0.3 inches of water

Monitoring Frequency: CONTINUOUS

Averaging Method: MAXIMUM - NOT TO BE EXCEEDED AT ANY
TIME (INSTANTANEOUS/DISCRETE OR GRAB)

Reporting Requirements: SEMI-ANNUALLY (CALENDAR)

Reports due 30 days after the reporting period.

Subsequent reports are due every 6 calendar month(s).

Condition 389: Compliance Certification

Effective between the dates of 01/07/2008 and Permit Expiration Date

Applicable Federal Requirement: 40CFR 63.1209(p), Subpart EEE

Expired by Mod 1

Item 389.1:

The Compliance Certification activity will be performed for the facility:

The Compliance Certification applies to:

Emission Unit: C-27018

Process: 424

Emission Source: 936FB

Emission Unit: C-27018

Process: 425

Emission Source: 936FB

Item 389.2:

Compliance Certification shall include the following monitoring:



Monitoring Type: MONITORING OF PROCESS OR CONTROL
DEVICE PARAMETERS AS SURROGATE

Monitoring Description:

If you comply with the requirements for combustion system leaks under §63.1206(c)(5) by maintaining the maximum combustion chamber zone pressure lower than ambient pressure to prevent combustion systems leaks from hazardous waste combustion, you must perform instantaneous monitoring of pressure and the automatic waste feed cutoff system must be engaged when negative pressure is not adequately maintained.

If the monitored parameter exceeds the limitation, the automatic waste feed cutoff must immediately and automatically cut off of the hazardous waste feed, except as provided by Section 63.1206(c)(3)(viii). In accordance with 63.1206(c)(2)(v)(2), an exceedance of this emission standard is not a violation of 40 CFR Part 63, Subpart EEE if you take the corrective measures prescribed in the startup, shutdown, and malfunction plan.

Combustion chamber zone pressure will be monitored continuously and will be maintained at a maximum of negative 0.3 inches of water at all times.

Parameter Monitored: PRESSURE

Upper Permit Limit: -0.3 inches of water

Monitoring Frequency: CONTINUOUS

Averaging Method: MAXIMUM - NOT TO BE EXCEEDED AT ANY
TIME (INSTANTANEOUS/DISCRETE OR GRAB)

Reporting Requirements: SEMI-ANNUALLY (CALENDAR)

Reports due 30 days after the reporting period.

The initial report is due 7/30/2008.

Subsequent reports are due every 6 calendar month(s).

Condition 1-40: Compliance Certification
Effective for entire length of Permit

Applicable Federal Requirement: 40CFR 63.2450(f), Subpart FFFF

Item 1-40.1:

The Compliance Certification activity will be performed for the facility:

The Compliance Certification applies to:

Emission Unit: C-27018

Emission Point: 62007

Regulated Contaminant(s):

CAS No: 0NY100-00-0 HAP

Item 1-40.2:

Compliance Certification shall include the following monitoring:



Monitoring Type: RECORD KEEPING/MAINTENANCE PROCEDURES

Monitoring Description:

If you use a halogen reduction device to reduce hydrogen halide and halogen HAP emissions from halogenated vent streams, you must meet the requirements of §63.994 and the requirements referenced therein. If you use a halogen reduction device before a combustion device, you must determine the halogen atom emission rate prior to the combustion device according to the procedures in §63.115(d)(2)(v).

Monitoring Frequency: AS REQUIRED - SEE PERMIT MONITORING DESCRIPTION

Reporting Requirements: AS REQUIRED - SEE MONITORING DESCRIPTION

Condition 1-41: Compliance Certification
Effective for entire length of Permit

Applicable Federal Requirement:40CFR 63.2455(a), Subpart FFFF

Item 1-41.1:

The Compliance Certification activity will be performed for the facility:

The Compliance Certification applies to:

Emission Unit: F-INISH

Emission Point: 76006

Regulated Contaminant(s):

CAS No: 000067-56-1	METHYL ALCOHOL
CAS No: 000075-36-5	ACETYL CHLORIDE
CAS No: 007647-01-0	HYDROGEN CHLORIDE
CAS No: 068479-14-1	SILANE, CHLORO METHYL DERIVS
CAS No: 000064-19-7	ACETIC ACID

Item 1-41.2:

Compliance Certification shall include the following monitoring:

Monitoring Type: MONITORING OF PROCESS OR CONTROL DEVICE PARAMETERS AS SURROGATE

Monitoring Description:

Water flow to the third stage of the scrubber will be monitored to ensure sufficient control efficiency. The lower limit of monitoring ensures compliance with all process batch operations under 6 NYCRR 212.9(b). Engineering calculations will be used as evidence of compliance under 6 NYCRR 212.9(b) with contaminant control efficiency when the measured flow rate falls below the lower limit of monitoring.

Compliance with this monitoring requirement assures compliance with Subpart FFFF 63.2465(a) and 212.9(b) per the Pre-Compliance Report.

Parameter Monitored: VOLUMETRIC FLOW RATE



Lower Permit Limit: 6.0 gallons per minute
Monitoring Frequency: CONTINUOUS
Averaging Method: 24-HOUR AVERAGE
Reporting Requirements: SEMI-ANNUALLY (CALENDAR)
Reports due 30 days after the reporting period.
Subsequent reports are due every 6 calendar month(s).

Condition 1-42: Compliance Certification
Effective for entire length of Permit

Applicable Federal Requirement:40CFR 63.2455(a), Subpart FFFF

Item 1-42.1:

The Compliance Certification activity will be performed for the facility:
The Compliance Certification applies to:

Emission Unit: F-INISH Emission Point: 76006

Regulated Contaminant(s):
CAS No: 000067-56-1 METHYL ALCOHOL
CAS No: 000075-36-5 ACETYL CHLORIDE
CAS No: 007647-01-0 HYDROGEN CHLORIDE
CAS No: 068479-14-1 SILANE, CHLORO METHYL DERIVS
CAS No: 000064-19-7 ACETIC ACID

Item 1-42.2:

Compliance Certification shall include the following monitoring:

Monitoring Type: MONITORING OF PROCESS OR CONTROL
DEVICE PARAMETERS AS SURROGATE

Monitoring Description:

Water flow to the second stage of the scrubber will be monitored to ensure sufficient control efficiency. The lower limit of monitoring ensures compliance with all process batch operations under 6 NYCRR 212.9(b). Engineering calculations will be used as evidence of compliance under 6 NYCRR 212.9(b) with contaminant control efficiency when the measured flow rate falls below the lower limit of monitoring.

Compliance with this monitoring requirement assures compliance with Subpart FFFF 63.2465(a) and 212.9(b) per the Pre-Compliance Report.

Parameter Monitored: VOLUMETRIC FLOW RATE

Lower Permit Limit: 6.9 gallons per minute
Monitoring Frequency: CONTINUOUS
Averaging Method: 24-HOUR AVERAGE
Reporting Requirements: SEMI-ANNUALLY (CALENDAR)
Reports due 30 days after the reporting period.
Subsequent reports are due every 6 calendar month(s).

Condition 1-43: Compliance Certification



Effective for entire length of Permit

Applicable Federal Requirement:40CFR 63.2455(a), Subpart FFFF

Item 1-43.1:

The Compliance Certification activity will be performed for the facility:
The Compliance Certification applies to:

Emission Unit: F-INISH

Emission Point: 76006

Regulated Contaminant(s):

CAS No: 000067-56-1

METHYL ALCOHOL

CAS No: 000075-36-5

ACETYL CHLORIDE

CAS No: 007647-01-0

HYDROGEN CHLORIDE

CAS No: 068479-14-1

SILANE, CHLORO METHYL DERIVS

CAS No: 000064-19-7

ACETIC ACID

Item 1-43.2:

Compliance Certification shall include the following monitoring:

Monitoring Type: MONITORING OF PROCESS OR CONTROL
DEVICE PARAMETERS AS SURROGATE

Monitoring Description:

Water flow to the first stage of the scrubber will be monitored to ensure sufficient control efficiency. The lower limit of monitoring ensures compliance with all process batch operations under 6 NYCRR 212.9(b). Engineering calculations will be used as evidence of compliance under 6 NYCRR 212.9(b) with contaminant control efficiency when the measured flow rate falls below the lower limit of monitoring.

Compliance with this monitoring requirement assures compliance with Subpart FFFF 63.2465(a) and 212.9(b) per the Pre-Compliance Report.

Parameter Monitored: VOLUMETRIC FLOW RATE

Lower Permit Limit: 19.4 gallons per minute

Monitoring Frequency: CONTINUOUS

Averaging Method: 24-HOUR AVERAGE

Reporting Requirements: SEMI-ANNUALLY (CALENDAR)

Reports due 30 days after the reporting period.

Subsequent reports are due every 6 calendar month(s).

Condition 1-44: Compliance Certification
Effective for entire length of Permit

Applicable Federal Requirement:40CFR 63.2455(a), Subpart FFFF

Item 1-44.1:

The Compliance Certification activity will be performed for the facility:
The Compliance Certification applies to:



Emission Unit: C-27018

Emission Point: 62007

Regulated Contaminant(s):

CAS No: 007647-01-0

HYDROGEN CHLORIDE

Item 1-44.2:

Compliance Certification shall include the following monitoring:

Monitoring Type: MONITORING OF PROCESS OR CONTROL
DEVICE PARAMETERS AS SURROGATE

Monitoring Description:

The scrubber water flow (ES-MCSVS) is monitored to ensure sufficient control efficiency. Engineering calculations will be used as evidence of compliance with control efficiency when the measured flow rate falls below the lower limit of monitoring.

Compliance with this monitoring requirement assures compliance with Subpart FFFF 63.2465(a) and 212.9(b) per the Pre-Compliance Report.

Parameter Monitored: VOLUMETRIC FLOW RATE

Lower Permit Limit: 100 gallons per minute

Monitoring Frequency: CONTINUOUS

Averaging Method: 24-HOUR AVERAGE

Reporting Requirements: SEMI-ANNUALLY (CALENDAR)

Reports due 30 days after the reporting period.

Subsequent reports are due every 6 calendar month(s).

**Condition 1-45: Compliance Certification
Effective for entire length of Permit**

Applicable Federal Requirement:40CFR 63.2455(a), Subpart FFFF

Item 1-45.1:

The Compliance Certification activity will be performed for the facility:

The Compliance Certification applies to:

Emission Unit: F-INISH

Emission Point: 76006

Regulated Contaminant(s):

CAS No: 000064-19-7

ACETIC ACID

CAS No: 000067-56-1

METHYL ALCOHOL

CAS No: 000075-36-5

ACETYL CHLORIDE

CAS No: 007647-01-0

HYDROGEN CHLORIDE

CAS No: 068479-14-1

SILANE, CHLORO METHYL DERIVS

Item 1-45.2:

Compliance Certification shall include the following monitoring:

Monitoring Type: MONITORING OF PROCESS OR CONTROL
DEVICE PARAMETERS AS SURROGATE

Monitoring Description:



Spray tower flow rate will be monitored to ensure sufficient control efficiency. The lower limit of monitoring ensures compliance with all process batch operations under 6 NYCRR 212.9(b). Engineering calculations will be used as evidence of compliance under 6 NYCRR 212.9(b) with contaminant control efficiency when the measured flow rate falls below the lower limit of monitoring.

Compliance with this monitoring requirement assures compliance with Subpart FFFF 63.2465(a) and 212.9(b) per the Pre-Compliance Report.

Parameter Monitored: VOLUMETRIC FLOW RATE

Lower Permit Limit: 13.4 gallons per minute

Monitoring Frequency: CONTINUOUS

Averaging Method: 24-HOUR AVERAGE

Reporting Requirements: SEMI-ANNUALLY (CALENDAR)

Reports due 30 days after the reporting period.

Subsequent reports are due every 6 calendar month(s).

Condition 420: Compliance Certification
Effective between the dates of 05/10/2008 and Permit Expiration Date

Applicable Federal Requirement: 40CFR 63.2455(a), Subpart FFFF

Expired by Mod 1

Item 420.1:

The Compliance Certification activity will be performed for the facility:

The Compliance Certification applies to:

Emission Unit: C-27018

Emission Point: 62007

Regulated Contaminant(s):

CAS No: 0NY100-00-0 HAP

Item 420.2:

Compliance Certification shall include the following monitoring:

Monitoring Type: RECORD KEEPING/MAINTENANCE PROCEDURES

Monitoring Description:

Emissions of total organic HAP from continuous process vents in an MCPU regulated under the MON must be reduced by =98 percent by weight or to an outlet process concentration =20 ppmv as organic HAP or TOC by venting emissions through a closed-vent system to any combination of control devices (except a flare).

Group 1 continuous process vents from this process are routed to the existing MCS vent incinerator (MCSVI) and scrubber (MCSVS) for control of organic HAP. In addition, two surge control vessels (62TRD) meet the capacity and vapor threshold of Group 1 storage tanks; emissions from



these vessels also are routed to MCSVI and MCSVS.

The temperature in the fire box will be monitored continuously in accordance with 40 CFR 63.988(c)(1). The minimum allowable temperature will be determined during the initial compliance test to be conducted in accordance with 40 CFR 63.2460(c). Records will be maintained in accordance with 40 CFR Section 63.998.

Compliance with this monitoring activity also assures compliance with requirements under 40 CFR 63.2450(r)

The correct Monitoring Type is: "Monitoring of Process or Control Device Parameters as Surrogate"

The Parameter Monitored is: "Temperature"

The Monitoring Frequency is: "Continuous"

The Averaging Method is: "Minimum- Not to Fall Below Stated Value - See Monitoring Description"

The Minimum Allowable Temperature (deg C) will be established by testing prior to the compliance date of this monitoring condition.

Monitoring Frequency: CONTINUOUS

Reporting Requirements: AS REQUIRED - SEE MONITORING DESCRIPTION

Condition 421: Compliance Certification
Effective between the dates of 05/10/2008 and Permit Expiration Date

Applicable Federal Requirement:40CFR 63.2455(a), Subpart FFFF

Expired by Mod 1

Item 421.1:

The Compliance Certification activity will be performed for the facility:
The Compliance Certification applies to:

Emission Unit: F-INISH

Emission Point: 76006

Regulated Contaminant(s):

CAS No: 0NY100-00-0 HAP

Item 421.2:

Compliance Certification shall include the following monitoring:

Monitoring Type: RECORD KEEPING/MAINTENANCE PROCEDURES

Monitoring Description:

Emissions of total organic HAP from continuous process vents in an MCPU regulated under the MON must be reduced by =98 percent by weight or to an outlet process concentration =20 ppmv as organic HAP or TOC by venting emissions through a closed-vent system to any combination of control devices (except a flare).



Group 1 continuous process vents from these processes are routed to an existing scrubber (76CSS) for control of organic HAP. The scrubbing liquid temperature and the specific gravity will be monitored continuously in accordance with 40 CFR 63.990(c)(1). If the difference between the specific gravity of the saturated scrubbing fluid and specific gravity of the fresh scrubbing fluid is less than 0.02 specific gravity units, an organic monitoring device capable of providing a continuous record shall be used. The minimum allowable specific gravity differential will be determined during the initial compliance test to be conducted in accordance with 40 CFR 63.2460(c). Records will be maintained in accordance with 40 CFR Section 63.998.

The correct Monitoring Type is: "Monitoring of Process or Control Device Parameters as Surrogate"

The Parameter Monitored is: "Specific Gravity"

The Monitoring Frequency is: "Continuous"

The Averaging Method is: "24 Hour Block Average"

The Minimum Allowable Specific Gravity will be established by testing prior to the compliance date of this monitoring condition.

Monitoring Frequency: CONTINUOUS

Reporting Requirements: AS REQUIRED - SEE MONITORING DESCRIPTION

Condition 1-46: Compliance Certification
Effective for entire length of Permit

Applicable Federal Requirement: 40CFR 63.2465(a), Subpart FFFF

Item 1-46.1:

The Compliance Certification activity will be performed for the facility:

The Compliance Certification applies to:

Emission Unit: C-27018

Emission Point: 76710

Emission Unit: C-27018

Emission Point: 76711

Regulated Contaminant(s):

CAS No: 000067-56-1

METHYL ALCOHOL

CAS No: 000075-36-5

ACETYL CHLORIDE

CAS No: 000075-65-0

2-METHYL-2-PROPANOL

CAS No: 001112-39-6

SILANE, DIMETHOXYDIMETHYL

CAS No: 007647-01-0

HYDROGEN CHLORIDE

CAS No: 000067-64-1

DIMETHYL KETONE

Item 1-46.2:

Compliance Certification shall include the following monitoring:

Monitoring Type: MONITORING OF PROCESS OR CONTROL
 DEVICE PARAMETERS AS SURROGATE



Monitoring Description:

High acid scrubber water flow will be monitored to ensure sufficient control efficiency. The lower limit of monitoring ensures compliance with all process batch operations. Engineering calculations will be used as evidence of compliance with contaminant control efficiency when the measured flow rate falls below the lower limit of monitoring.

Compliance with this monitoring requirement assures compliance with 212.9(b) per the Pre-Compliance Report.

Parameter Monitored: VOLUMETRIC FLOW RATE

Lower Permit Limit: 40 gallons per minute

Monitoring Frequency: CONTINUOUS

Averaging Method: 24 HOUR DAILY BLOCK (ARITHMETIC AVERAGE)

Reporting Requirements: SEMI-ANNUALLY (CALENDAR)

Reports due 30 days after the reporting period.

Subsequent reports are due every 6 calendar month(s).

**Condition 1-47: Compliance Certification
Effective for entire length of Permit**

Applicable Federal Requirement: 40CFR 63.2465(a), Subpart FFFF

Item 1-47.1:

The Compliance Certification activity will be performed for the facility:

The Compliance Certification applies to:

Emission Unit: C-27018

Emission Point: 76001

Regulated Contaminant(s):

CAS No: 000067-56-1	METHYL ALCOHOL
CAS No: 000067-64-1	DIMETHYL KETONE
CAS No: 000075-36-5	ACETYL CHLORIDE
CAS No: 000075-78-5	DIMETHYLDICHLOROSILANE
CAS No: 000075-79-6	METHYLTRICHLOROSILANE
CAS No: 000107-46-0	HEXAMETHYLDISILOXANE
CAS No: 000108-88-3	TOLUENE
CAS No: 000124-70-9	SILANE, DICHLOROETHENYLMETHYL
CAS No: 000556-67-2	OCTAMETHYLCYCLOTETRA SILOXANE
CAS No: 001112-39-6	SILANE, DIMETHOXYDIMETHYL
CAS No: 001185-55-3	METHYLTRIMETHOXYSILOXANE
CAS No: 001719-58-0	SILANE, CHLOROETHENYLDIMETHYL
CAS No: 007647-01-0	HYDROGEN CHLORIDE
CAS No: 010026-04-7	TETRACHLORO SILANE
CAS No: 068479-14-1	SILANE, CHLORO METHYL DERIVS
CAS No: 000064-19-7	ACETIC ACID

Item 1-47.2:

Compliance Certification shall include the following monitoring:



Monitoring Type: MONITORING OF PROCESS OR CONTROL
DEVICE PARAMETERS AS SURROGATE

Monitoring Description:

A flow meter is used to monitor the water flow rate to the scrubber to ensure sufficient control efficiency. Engineering calculations will be used as evidence of compliance with control efficiency when the measured flow rate falls below the lower limit of monitoring.

Compliance with this monitoring requirement assures compliance with 212.9(b) per the Pre-Compliance Report.

Parameter Monitored: VOLUMETRIC FLOW RATE

Lower Permit Limit: 72 gallons per minute

Monitoring Frequency: CONTINUOUS

Averaging Method: 24 HOUR DAILY AVERAGE (ARITHMETIC MEAN)

Reporting Requirements: SEMI-ANNUALLY (CALENDAR)

Reports due 30 days after the reporting period.

Subsequent reports are due every 6 calendar month(s).

Condition 1-48: Compliance Certification
Effective for entire length of Permit

Applicable Federal Requirement: 40CFR 63.2465(a), Subpart FFFF

Item 1-48.1:

The Compliance Certification activity will be performed for the facility:

The Compliance Certification applies to:

Emission Unit: C-27018

Emission Point: 35017

Regulated Contaminant(s):

CAS No: 000556-67-2

OCTAMETHYLCYCLOTETRA SILOXANE

Item 1-48.2:

Compliance Certification shall include the following monitoring:

Monitoring Type: MONITORING OF PROCESS OR CONTROL
DEVICE PARAMETERS AS SURROGATE

Monitoring Description:

The water flow to the scrubber is monitored to ensure the scrubber is operating at the required control efficiency. Engineering calculations will be used as evidence of compliance with control efficiency when the measured flow rate falls below the lower limit of monitoring.

Compliance with this monitoring requirement assures compliance with 212.9(b) per the Pre-Compliance Report.

Parameter Monitored: VOLUMETRIC FLOW RATE



Lower Permit Limit: 1.5 gallons per minute
Monitoring Frequency: CONTINUOUS
Averaging Method: 24-HOUR AVERAGE
Reporting Requirements: SEMI-ANNUALLY (CALENDAR)
Reports due 30 days after the reporting period.
Subsequent reports are due every 6 calendar month(s).

Condition 1-49: Compliance Certification
Effective for entire length of Permit

Applicable Federal Requirement:40CFR 63.2465(a), Subpart FFFF

Item 1-49.1:

The Compliance Certification activity will be performed for the facility:
The Compliance Certification applies to:

Emission Unit: C-27018 Emission Point: 27024

Regulated Contaminant(s):
CAS No: 007647-01-0 HYDROGEN CHLORIDE

Item 1-49.2:

Compliance Certification shall include the following monitoring:

Monitoring Type: MONITORING OF PROCESS OR CONTROL
DEVICE PARAMETERS AS SURROGATE

Monitoring Description:

The scrubber temperature will be monitored to ensure the scrubber is operating at the required control efficiency. Engineering calculations will be used as evidence of compliance with control efficiency when the measured parameter exceeds the upper limit of monitoring.

Compliance with this monitoring requirement assures compliance with 212.9(b) per the Pre-Compliance Report.

Parameter Monitored: TEMPERATURE

Upper Permit Limit: 95 degrees C below the approved
performance test combustion
temperature

Monitoring Frequency: CONTINUOUS
Averaging Method: 24-HOUR AVERAGE
Reporting Requirements: SEMI-ANNUALLY (CALENDAR)
Reports due 30 days after the reporting period.
Subsequent reports are due every 6 calendar month(s).

Condition 1-50: Compliance Certification
Effective for entire length of Permit

Applicable Federal Requirement:40CFR 63.2465(a), Subpart FFFF

Item 1-50.1:



The Compliance Certification activity will be performed for the facility:
The Compliance Certification applies to:

Emission Unit: C-27035

Emission Point: 27035

Regulated Contaminant(s):

CAS No: 007647-01-0

HYDROGEN CHLORIDE

Item 1-50.2:

Compliance Certification shall include the following monitoring:

Monitoring Type: MONITORING OF PROCESS OR CONTROL
DEVICE PARAMETERS AS SURROGATE

Monitoring Description:

The packed tower water scrubber flow is maintained at a minimum of 5 gpm to ensure 99% control efficiency for Part 212. Engineering calculations will be used as evidence of compliance with control efficiency when the measured flow rate falls below the lower limit of monitoring.

Compliance with this monitoring requirement assures compliance with 212.9(b) per the Pre-Compliance Report.

Parameter Monitored: VOLUMETRIC FLOW RATE

Lower Permit Limit: 5 gallons per minute

Monitoring Frequency: CONTINUOUS

Averaging Method: 24-HOUR AVERAGE

Reporting Requirements: SEMI-ANNUALLY (CALENDAR)

Reports due 30 days after the reporting period.

Subsequent reports are due every 6 calendar month(s).

Condition 430: Compliance Certification

Effective between the dates of 05/10/2008 and Permit Expiration Date

Applicable Federal Requirement:40CFR 63.2465(a), Subpart FFFF

Expired by Mod 1

Item 430.1:

The Compliance Certification activity will be performed for the facility:
The Compliance Certification applies to:

Emission Unit: C-27018

Emission Point: 76001

Regulated Contaminant(s):

CAS No: ONY100-00-0

HAP

Item 430.2:

Compliance Certification shall include the following monitoring:

Monitoring Type: RECORD KEEPING/MAINTENANCE PROCEDURES

Monitoring Description:

Processes with uncontrolled hydrogen halide and halogen



HAP emissions from process vents =1,000 lb/yr must reduce collective hydrogen halide and halogen HAP emissions by =99 percent by weight or to an outlet concentration <20 ppmv by venting through a closed-vent system to any combination of control devices.

The subject process vents from this process are vented to a venturi scrubber (76EWS). The pH of the scrubber effluent will be monitored continuously in accordance with 40 CFR 63.994(c)(1). The minimum allowable pH will be determined during the initial compliance test to be conducted in accordance with 40 CFR 63.994(b). Records will be maintained in accordance with 40 CFR Section 63.998. General requirements for monitoring and continuous parameter monitoring systems are contained in a referencing subpart and §63.996.

The correct Monitoring Type is: "Monitoring of Process or Control Device Parameters as Surrogate"

The Parameter Monitored is: "ph"

The Monitoring Frequency is: "As Required - See Permit Monitoring Description"

The Averaging Method is: "Minimum- Not to Fall Below Stated Value - See Monitoring Description"

The Minimum Allowable pH will be established by testing prior to the compliance date of this monitoring condition.

Monitoring Frequency: AS REQUIRED - SEE PERMIT MONITORING DESCRIPTION

Reporting Requirements: AS REQUIRED - SEE MONITORING DESCRIPTION

Condition 431: Compliance Certification

Effective between the dates of 05/10/2008 and Permit Expiration Date

Applicable Federal Requirement:40CFR 63.2465(a), Subpart FFFF

Expired by Mod 1

Item 431.1:

The Compliance Certification activity will be performed for the facility:
The Compliance Certification applies to:

Emission Unit: C-27035

Emission Point: 27035

Regulated Contaminant(s):

CAS No: 0NY100-00-0 HAP

Item 431.2:

Compliance Certification shall include the following monitoring:

Monitoring Type: RECORD KEEPING/MAINTENANCE PROCEDURES

Monitoring Description:

Processes with uncontrolled hydrogen halide and halogen



HAP emissions from process vents =1,000 lb/yr must reduce collective hydrogen halide and halogen HAP emissions by =99 percent by weight or to an outlet concentration <20 ppmv by venting through a closed-vent system to any combination of control devices.

The subject process vents from this process are vented to the B35 HCl fume scrubber (27HWT) only during times of startup, shutdown, and malfunction. The pH of the scrubber effluent will be monitored continuously in accordance with 40 CFR 63.994(c)(1). The minimum allowable pH will be determined during the initial compliance test to be conducted in accordance with 40 CFR 63.994(b). Records will be maintained in accordance with 40 CFR Section 63.998. General requirements for monitoring and continuous parameter monitoring systems are contained in a referencing subpart and §63.996.

The correct Monitoring Type is: "Monitoring of Process or Control Device Parameters as Surrogate"

The Parameter Monitored is: "ph"

The Monitoring Frequency is: "As Required - See Permit Monitoring Description"

The Averaging Method is: "Minimum- Not to Fall Below Stated Value - See Monitoring Description"

The Minimum Allowable pH will be established by testing prior to the compliance date of this monitoring condition.

Monitoring Frequency: AS REQUIRED - SEE PERMIT MONITORING DESCRIPTION

Reporting Requirements: AS REQUIRED - SEE MONITORING DESCRIPTION

Condition 432: Compliance Certification
Effective between the dates of 05/10/2008 and Permit Expiration Date

Applicable Federal Requirement:40CFR 63.2465(a), Subpart FFFF

Expired by Mod 1

Item 432.1:

The Compliance Certification activity will be performed for the facility:

The Compliance Certification applies to:

Emission Unit: C-27035

Emission Point: 27035

Regulated Contaminant(s):

CAS No: 0NY100-00-0 HAP

Item 432.2:

Compliance Certification shall include the following monitoring:

Monitoring Type: RECORD KEEPING/MAINTENANCE PROCEDURES



Monitoring Description:

Processes with uncontrolled hydrogen halide and halogen HAP emissions from process vents =1,000 lb/yr must reduce collective hydrogen halide and halogen HAP emissions by =99 percent by weight or to an outlet concentration <20 ppmv by venting through a closed-vent system to any combination of control devices.

The subject process vents from this process are vented to the B35 HCl fume scrubber (27HWT) only during times of startup, shutdown, and malfunction. The flow rate of the scrubber effluent will be monitored continuously in accordance with 40 CFR 63.994(c)(1). The minimum allowable flow rate will be determined during the initial compliance test to be conducted in accordance with 40 CFR 63.994(b). Gas stream flow shall be determined using one of the procedures specified in paragraphs (c)(1)(ii)(A) through (D) of this section. Records will be maintained in accordance with 40 CFR Section 63.998. General requirements for monitoring and continuous parameter monitoring systems are contained in a referencing subpart and §63.996.

The correct Monitoring Type is: "Monitoring of Process or Control Device Parameters as Surrogate"
The Parameter Monitored is: "Flow Rate"
The Monitoring Frequency is: "Continuous"
The Averaging Method is: "Minimum- Not to Fall Below Stated Value - See Monitoring Description"
The Minimum Allowable Flow Rate will be established by testing prior to the compliance date of this monitoring condition.

Monitoring Frequency: CONTINUOUS

Reporting Requirements: AS REQUIRED - SEE MONITORING DESCRIPTION

Condition 433: Compliance Certification

Effective between the dates of 05/10/2008 and Permit Expiration Date

Applicable Federal Requirement:40CFR 63.2465(a), Subpart FFFF

Expired by Mod 1

Item 433.1:

The Compliance Certification activity will be performed for the facility:

The Compliance Certification applies to:

Emission Unit: C-27018

Emission Point: 76001

Regulated Contaminant(s):

CAS No: 0NY100-00-0 HAP

Item 433.2:

Compliance Certification shall include the following monitoring:



Monitoring Type: RECORD KEEPING/MAINTENANCE PROCEDURES

Monitoring Description:

Processes with uncontrolled hydrogen halide and halogen HAP emissions from process vents =1,000 lb/yr must reduce collective hydrogen halide and halogen HAP emissions by =99 percent by weight or to an outlet concentration <20 ppmv by venting through a closed-vent system to any combination of control devices.

The subject process vents from this process are vented to a venturi scrubber (76EWS). The flow rate of the scrubber effluent will be monitored continuously in accordance with 40 CFR 63.994(c)(1). The minimum allowable flow rate will be determined during the initial compliance test to be conducted in accordance with 40 CFR 63.994(b). Gas stream flow shall be determined using one of the procedures specified in paragraphs (c)(1)(ii)(A) through (D) of this section. Records will be maintained in accordance with 40 CFR Section 63.998. General requirements for monitoring and continuous parameter monitoring systems are contained in a referencing subpart and §63.996.

The correct Monitoring Type is: "Monitoring of Process or Control Device Parameters as Surrogate"
The Parameter Monitored is: "Flow Rate"
The Monitoring Frequency is: "Continuous"
The Averaging Method is: "Minimum- Not to Fall Below Stated Value - See Monitoring Description"
The Minimum Allowable Flow Rate will be established by testing prior to the compliance date of this monitoring condition.

Monitoring Frequency: CONTINUOUS

Reporting Requirements: AS REQUIRED - SEE MONITORING DESCRIPTION

Condition 434: Compliance Certification

Effective between the dates of 05/10/2008 and Permit Expiration Date

Applicable Federal Requirement:40CFR 63.2465(a), Subpart FFFF

Expired by Mod 1

Item 434.1:

The Compliance Certification activity will be performed for the facility:

The Compliance Certification applies to:

Emission Unit: C-27018

Emission Point: 62007

Regulated Contaminant(s):

CAS No: 0NY100-00-0 HAP

Item 434.2:

Compliance Certification shall include the following monitoring:



Monitoring Type: RECORD KEEPING/MAINTENANCE PROCEDURES

Monitoring Description:

Processes with uncontrolled hydrogen halide and halogen HAP emissions from process vents =1,000 lb/yr must reduce collective hydrogen halide and halogen HAP emissions by =99 percent by weight or to an outlet concentration <20 ppmv by venting through a closed-vent system to any combination of control devices.

The subject process vents from this process are routed to the existing MCS scrubber (MCSV) and vent incinerator (MCSVI). The pH of the scrubber effluent will be monitored continuously in accordance with 40 CFR 63.994(c)(1). The minimum allowable pH will be determined during the initial compliance test to be conducted in accordance with 40 CFR 63.994(b). Records will be maintained in accordance with 40 CFR Section 63.998. General requirements for monitoring and continuous parameter monitoring systems are contained in a referencing subpart and §63.996.

The correct Monitoring Type is: "Monitoring of Process or Control Device Parameters as Surrogate"

The Parameter Monitored is: "ph"

The Monitoring Frequency is: "As Required - See Permit Monitoring Description"

The Averaging Method is: "Minimum- Not to Fall Below Stated Value - See Monitoring Description"

The Minimum Allowable pH will be established by testing prior to the compliance date of this monitoring condition.

Monitoring Frequency: AS REQUIRED - SEE PERMIT MONITORING DESCRIPTION

Reporting Requirements: AS REQUIRED - SEE MONITORING DESCRIPTION

Condition 435: Compliance Certification
Effective between the dates of 05/10/2008 and Permit Expiration Date

Applicable Federal Requirement:40CFR 63.2465(a), Subpart FFFF

Expired by Mod 1

Item 435.1:

The Compliance Certification activity will be performed for the facility:

The Compliance Certification applies to:

Emission Unit: C-27018

Emission Point: 62007

Regulated Contaminant(s):

CAS No: 0NY100-00-0 HAP

Item 435.2:



Compliance Certification shall include the following monitoring:

Monitoring Type: RECORD KEEPING/MAINTENANCE PROCEDURES

Monitoring Description:

Processes with uncontrolled hydrogen halide and halogen HAP emissions from process vents =1,000 lb/yr must reduce collective hydrogen halide and halogen HAP emissions by =99 percent by weight or to an outlet concentration <20 ppmv by venting through a closed-vent system to any combination of control devices.

The subject process vents from this process are routed to the existing MCS scrubber (MCSV) and vent incinerator (MCSVI). The flow rate of the scrubber effluent will be monitored continuously in accordance with 40 CFR 63.994(c)(1). The minimum allowable flow rate will be determined during the initial compliance test to be conducted in accordance with 40 CFR 63.994(b). Gas stream flow shall be determined using one of the procedures specified in paragraphs (c)(1)(ii)(A) through (D) of this section. Records will be maintained in accordance with 40 CFR Section 63.998. General requirements for monitoring and continuous parameter monitoring systems are contained in a referencing subpart and §63.996.

The correct Monitoring Type is: "Monitoring of Process or Control Device Parameters as Surrogate"
The Parameter Monitored is: "Flow Rate"
The Monitoring Frequency is: "Continuous"
The Averaging Method is: "Minimum- Not to Fall Below Stated Value - See Monitoring Description"
The Minimum Allowable Flow Rate will be established by testing prior to the compliance date of this monitoring condition.

Monitoring Frequency: CONTINUOUS

Reporting Requirements: AS REQUIRED - SEE MONITORING DESCRIPTION

Condition 436: Compliance Certification
Effective between the dates of 05/10/2008 and Permit Expiration Date

Applicable Federal Requirement:40CFR 63.2465(a), Subpart FFFF

Expired by Mod 1

Item 436.1:

The Compliance Certification activity will be performed for the facility:

The Compliance Certification applies to:

Emission Unit: F-INISH

Emission Point: 76006

Regulated Contaminant(s):

CAS No: 0NY100-00-0 HAP



Item 436.2:

Compliance Certification shall include the following monitoring:

Monitoring Type: RECORD KEEPING/MAINTENANCE PROCEDURES

Monitoring Description:

Processes with uncontrolled hydrogen halide and halogen HAP emissions from process vents =1,000 lb/yr must reduce collective hydrogen halide and halogen HAP emissions by =99 percent by weight or to an outlet concentration <20 ppmv by venting through a closed-vent system to any combination of control devices.

The subject process vents from these processes are vented to the CASH scrubber (76CSS). The pH of the scrubber effluent will be monitored continuously in accordance with 40 CFR 63.994(c)(1). The minimum allowable pH will be determined during the initial compliance test to be conducted in accordance with 40 CFR 63.994(b). Records will be maintained in accordance with 40 CFR Section 63.998. General requirements for monitoring and continuous parameter monitoring systems are contained in a referencing subpart and §63.996.

The correct Monitoring Type is: "Monitoring of Process or Control Device Parameters as Surrogate"

The Parameter Monitored is: "ph"

The Monitoring Frequency is: "As Required - See Permit Monitoring Description"

The Averaging Method is: "Minimum- Not to Fall Below Stated Value - See Monitoring Description"

The Minimum Allowable pH will be established by testing prior to the compliance date of this monitoring condition.

Monitoring Frequency: AS REQUIRED - SEE PERMIT MONITORING DESCRIPTION

Reporting Requirements: AS REQUIRED - SEE MONITORING DESCRIPTION

Condition 437: Compliance Certification

Effective between the dates of 05/10/2008 and Permit Expiration Date

Applicable Federal Requirement:40CFR 63.2465(a), Subpart FFFF

Expired by Mod 1

Item 437.1:

The Compliance Certification activity will be performed for the facility:

The Compliance Certification applies to:

Emission Unit: F-INISH

Emission Point: 76006

Regulated Contaminant(s):

CAS No: 0NY100-00-0 HAP



Item 437.2:

Compliance Certification shall include the following monitoring:

Monitoring Type: RECORD KEEPING/MAINTENANCE PROCEDURES

Monitoring Description:

Processes with uncontrolled hydrogen halide and halogen HAP emissions from process vents =1,000 lb/yr must reduce collective hydrogen halide and halogen HAP emissions by =99 percent by weight or to an outlet concentration <20 ppmv by venting through a closed-vent system to any combination of control devices.

The subject process vents from these processes are vented to the CASH scrubber (76CSS). The flow rate of the scrubber effluent will be monitored continuously in accordance with 40 CFR 63.994(c)(1). The minimum allowable flow rate will be determined during the initial compliance test to be conducted in accordance with 40 CFR 63.994(b). Gas stream flow shall be determined using one of the procedures specified in paragraphs (c)(1)(ii)(A) through (D) of this section. Records will be maintained in accordance with 40 CFR Section 63.998. General requirements for monitoring and continuous parameter monitoring systems are contained in a referencing subpart and §63.996.

The correct Monitoring Type is: "Monitoring of Process or Control Device Parameters as Surrogate"

The Parameter Monitored is: "Flow Rate"

The Monitoring Frequency is: "Continuous"

The Averaging Method is: "Minimum- Not to Fall Below Stated Value - See Monitoring Description"

The Minimum Allowable Flow Rate will be established by testing prior to the compliance date of this monitoring condition.

Monitoring Frequency: CONTINUOUS

Reporting Requirements: AS REQUIRED - SEE MONITORING DESCRIPTION

****** Emission Unit Level ******

**Condition 476: Emission Point Definition By Emission Unit
Effective between the dates of 01/07/2008 and Permit Expiration Date**

Applicable Federal Requirement:6NYCRR 201-6

Item 476.1(From Mod 1):

The following emission points are included in this permit for the cited Emission Unit:

Emission Unit: C-27018



Emission Point: 21005			
Height (ft.): 30	Diameter (in.): 2		Building: 21
Emission Point: 23002			
Height (ft.): 18	Diameter (in.): 37		
NYTMN (km.): 4741.324	NYTME (km.): 609.133		Building: 23
Emission Point: 23005			
Height (ft.): 10	Diameter (in.): 3		
NYTMN (km.): 4741.324	NYTME (km.): 609.133		Building: 23
Emission Point: 24103			
Height (ft.): 80	Diameter (in.): 2		
NYTMN (km.): 4741.324	NYTME (km.): 609.133		Building: 24A
Emission Point: 24113			
Height (ft.): 8	Diameter (in.): 8		
			Building: 24
Emission Point: 24120			
Height (ft.): 137	Diameter (in.): 10		
NYTMN (km.): 4741.324	NYTME (km.): 609.133		Building: 24A
Emission Point: 24121			
Height (ft.): 87	Diameter (in.): 1		
NYTMN (km.): 4741.324	NYTME (km.): 609.133		Building: 24
Emission Point: 24132			
Height (ft.): 21	Diameter (in.): 8		
NYTMN (km.): 4741.324	NYTME (km.): 609.133		Building: 24
Emission Point: 24133			
Height (ft.): 4	Diameter (in.): 2		
NYTMN (km.): 4741.324	NYTME (km.): 609.133		Building: 24
Emission Point: 24134			
Height (ft.): 55	Diameter (in.): 2		
NYTMN (km.): 4741.324	NYTME (km.): 609.133		Building: 24
Emission Point: 24135			
Height (ft.): 55	Diameter (in.): 2		
NYTMN (km.): 4741.324	NYTME (km.): 609.133		Building: 24
Emission Point: 24137			
Height (ft.): 10	Diameter (in.): 2		
NYTMN (km.): 4741.324	NYTME (km.): 609.133		Building: 24
Emission Point: 24139			
Height (ft.): 10	Diameter (in.): 2		
NYTMN (km.): 4741.324	NYTME (km.): 609.133		Building: 24



Emission Point: 24140	Height (ft.): 10	Diameter (in.): 2	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	
Emission Point: 24305	Height (ft.): 106	Diameter (in.): 3	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 24
Emission Point: 24307	Height (ft.): 73	Diameter (in.): 3	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 24
Emission Point: 24309	Height (ft.): 12	Diameter (in.): 3	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 24
Emission Point: 24310	Height (ft.): 137	Diameter (in.): 2	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 24
Emission Point: 24311	Height (ft.): 22	Diameter (in.): 2	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 24
Emission Point: 24312	Height (ft.): 134	Diameter (in.): 1	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 24
Emission Point: 24409	Height (ft.): 12	Diameter (in.): 2	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 24
Emission Point: 24423	Height (ft.): 40	Diameter (in.): 3	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 24
Emission Point: 24702	Height (ft.): 4	Diameter (in.): 2	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 24
Emission Point: 24704	Height (ft.): 4	Diameter (in.): 2	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 24
Emission Point: 24801	Height (ft.): 4	Diameter (in.): 2	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 24
Emission Point: 24906	Height (ft.): 15	Diameter (in.): 1	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 24
Emission Point: 24907			



Height (ft.): 10	Diameter (in.): 3	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 24
Emission Point: 24916		
Height (ft.): 134	Diameter (in.): 2	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 24
Emission Point: 24922		
Height (ft.): 15	Diameter (in.): 1	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 24
Emission Point: 24924		
Height (ft.): 10	Diameter (in.): 3	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 24
Emission Point: 24925		
Height (ft.): 11	Diameter (in.): 2	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 24
Emission Point: 24935		
Height (ft.): 10	Diameter (in.): 1	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 24
Emission Point: 24937		
Height (ft.): 11	Diameter (in.): 2	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 24
Emission Point: 24938		
Height (ft.): 12	Diameter (in.): 2	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 24
Emission Point: 24939		
Height (ft.): 12	Diameter (in.): 2	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 24
Emission Point: 24940		
Height (ft.): 30	Diameter (in.): 4	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 24
Emission Point: 24941		
Height (ft.): 8	Diameter (in.): 2	
		Building: 24
Emission Point: 24944		
Height (ft.): 0	Diameter (in.): 24	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 24
Emission Point: 24945		
Height (ft.): 0	Diameter (in.): 24	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 24
Emission Point: 24949		
Height (ft.): 134	Diameter (in.): 2	



			Building: 24
Emission Point: 24950	Height (ft.): 134	Diameter (in.): 2	
			Building: 24
Emission Point: 27018	Height (ft.): 6	Diameter (in.): 2	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 27
Emission Point: 27024	Height (ft.): 30	Diameter (in.): 8	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 27
Emission Point: 30801	Height (ft.): 45	Diameter (in.): 2	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 30
Emission Point: 30802	Height (ft.): 45	Diameter (in.): 2	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 30
Emission Point: 30803	Height (ft.): 45	Diameter (in.): 2	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 30
Emission Point: 30805	Height (ft.): 45	Diameter (in.): 2	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 30
Emission Point: 30901	Height (ft.): 12	Diameter (in.): 2	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 30
Emission Point: 30902	Height (ft.): 43	Diameter (in.): 3	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 30
Emission Point: 30910	Height (ft.): 15	Diameter (in.): 1	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 30
Emission Point: 30911	Height (ft.): 15	Diameter (in.): 1	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 30
Emission Point: 30912	Height (ft.): 27	Diameter (in.): 2	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 30
Emission Point: 30913	Height (ft.): 31	Diameter (in.): 2	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 30



Emission Point:	30915			
	Height (ft.): 7	Diameter (in.): 2		
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building:	30
Emission Point:	30933			
	Height (ft.): 18	Diameter (in.): 2		
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building:	30
Emission Point:	30935			
	Height (ft.): 18	Diameter (in.): 2		
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building:	30
Emission Point:	30945			
	Height (ft.): 15	Diameter (in.): 1		
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building:	30
Emission Point:	30946			
	Height (ft.): 15	Diameter (in.): 1		
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building:	30
Emission Point:	31041			
	Height (ft.): 46	Diameter (in.): 2		
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building:	30
Emission Point:	32035			
	Height (ft.): 82	Diameter (in.): 2		
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building:	30
Emission Point:	35006			
	Height (ft.): 66	Diameter (in.): 3		
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building:	35
Emission Point:	35017			
	Height (ft.): 24	Diameter (in.): 4		
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building:	35
Emission Point:	35018			
	Height (ft.): 27	Diameter (in.): 3		
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building:	35
Emission Point:	35028			
	Height (ft.): 0	Diameter (in.): 24		
			Building:	35
Emission Point:	35031			
	Height (ft.): 0	Diameter (in.): 1		
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building:	35
Emission Point:	35032			
	Height (ft.): 15	Diameter (in.): 1		
			Building:	35



Emission Point: 35033 Height (ft.): 15	Diameter (in.): 1	Building: 35
Emission Point: 35034 Height (ft.): 15	Diameter (in.): 1	Building: 35
Emission Point: 35035 Height (ft.): 15	Diameter (in.): 1	Building: 35
Emission Point: 35036 Height (ft.): 15	Diameter (in.): 1	Building: 35
Emission Point: 35037 Height (ft.): 15	Diameter (in.): 1	Building: 35
Emission Point: 35038 Height (ft.): 15	Diameter (in.): 1	Building: 35
Emission Point: 35039 Height (ft.): 15	Diameter (in.): 1	Building: 35
Emission Point: 35040 Height (ft.): 15	Diameter (in.): 1	Building: 35
Emission Point: 35041 Height (ft.): 15	Diameter (in.): 1	Building: 35
Emission Point: 35042 Height (ft.): 15	Diameter (in.): 1	Building: 35
Emission Point: 35048 Height (ft.): 25	Diameter (in.): 1	Building: 35
Emission Point: 35049 Height (ft.): 25	Diameter (in.): 1	Building: 35
Emission Point: 35050 Height (ft.): 25	Diameter (in.): 1	Building: 35
Emission Point: 35901		



Height (ft.): 42	Diameter (in.): 2	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 35
Emission Point: 36001		
Height (ft.): 12	Diameter (in.): 1	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 36
Emission Point: 36003		
Height (ft.): 12	Diameter (in.): 1	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 36
Emission Point: 36004		
Height (ft.): 12	Diameter (in.): 1	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 36
Emission Point: 37004		
Height (ft.): 45	Diameter (in.): 2	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 37
Emission Point: 37009		
Height (ft.): 44	Diameter (in.): 2	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 37
Emission Point: 37013		
Height (ft.): 45	Diameter (in.): 2	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 37
Emission Point: 37014		
Height (ft.): 56	Diameter (in.): 2	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 37
Emission Point: 37017		
Height (ft.): 45	Diameter (in.): 2	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 37
Emission Point: 37018		
Height (ft.): 45	Diameter (in.): 2	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 37
Emission Point: 37019		
Height (ft.): 51	Diameter (in.): 2	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 37
Emission Point: 37021		
Height (ft.): 45	Diameter (in.): 1	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 37
Emission Point: 37023		
Height (ft.): 7	Diameter (in.): 1	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 37
Emission Point: 37026		
Height (ft.): 42	Diameter (in.): 2	



NYTMN (km.): 4741.324 NYTME (km.): 609.133 Building: 37

Emission Point: 37027
 Height (ft.): 2 Diameter (in.): 1
 NYTMN (km.): 4741.324 NYTME (km.): 609.133 Building: 37

Emission Point: 37034
 Height (ft.): 56 Diameter (in.): 2
 NYTMN (km.): 4741.324 NYTME (km.): 609.133 Building: 37

Emission Point: 37038
 Height (ft.): 42 Diameter (in.): 2
 Building: 37

Emission Point: 37039
 Height (ft.): 42 Diameter (in.): 2
 Building: 37

Emission Point: 37053
 Height (ft.): 41 Diameter (in.): 1
 NYTMN (km.): 4741.324 NYTME (km.): 609.133 Building: 37

Emission Point: 37056
 Height (ft.): 40 Diameter (in.): 1
 NYTMN (km.): 4741.324 NYTME (km.): 609.133 Building: 37

Emission Point: 37062
 Height (ft.): 30 Diameter (in.): 1
 Building: 37

Emission Point: 37063
 Height (ft.): 30 Diameter (in.): 1
 Building: 37

Emission Point: 37077
 Height (ft.): 30 Diameter (in.): 2
 NYTMN (km.): 4741.324 NYTME (km.): 609.133 Building: 37

Emission Point: 37708
 Height (ft.): 43 Diameter (in.): 8
 Building: 37

Emission Point: 37801
 Height (ft.): 50 Diameter (in.): 2
 NYTMN (km.): 4741.324 NYTME (km.): 609.133 Building: 37

Emission Point: 37803
 Height (ft.): 55 Diameter (in.): 2
 NYTMN (km.): 4741.324 NYTME (km.): 609.133 Building: 37

Emission Point: 37805
 Height (ft.): 36 Diameter (in.): 2
 NYTMN (km.): 4741.324 NYTME (km.): 609.133 Building: 37



Emission Point: 37812			
Height (ft.): 50	Diameter (in.): 2		
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 37	
Emission Point: 37813			
Height (ft.): 34	Diameter (in.): 1		
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 37	
Emission Point: 37814			
Height (ft.): 30	Diameter (in.): 2		
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 37	
Emission Point: 37901			
Height (ft.): 40	Diameter (in.): 2		
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 37	
Emission Point: 37902			
Height (ft.): 55	Diameter (in.): 2		
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 37	
Emission Point: 37903			
Height (ft.): 55	Diameter (in.): 2		
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 37	
Emission Point: 37909			
Height (ft.): 25	Diameter (in.): 1		
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 37	
Emission Point: 37910			
Height (ft.): 25	Diameter (in.): 1		
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 37	
Emission Point: 37911			
Height (ft.): 54	Diameter (in.): 2		
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 37	
Emission Point: 37921			
Height (ft.): 25	Diameter (in.): 1		
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 37	
Emission Point: 37922			
Height (ft.): 20	Diameter (in.): 1		
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 37	
Emission Point: 37926			
Height (ft.): 10	Diameter (in.): 1		
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 37	
Emission Point: 37927			
Height (ft.): 21	Diameter (in.): 2		
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 37	



Emission Point: 37928			
Height (ft.): 41	Diameter (in.): 1		
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 37	
Emission Point: 37931			
Height (ft.): 41	Diameter (in.): 2		
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 37	
Emission Point: 37934			
Height (ft.): 43	Diameter (in.): 11		
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 37	
Emission Point: 37946			
Height (ft.): 20	Diameter (in.): 1		
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 37	
Emission Point: 37947			
Height (ft.): 20	Diameter (in.): 1		
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 37	
Emission Point: 37952			
Height (ft.): 64	Diameter (in.): 2		
		Building: 37	
Emission Point: 38006			
Height (ft.): 20	Diameter (in.): 1		
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 38	
Emission Point: 38007			
Height (ft.): 20	Diameter (in.): 1		
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 38	
Emission Point: 38018			
Height (ft.): 1	Diameter (in.): 1		
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 38	
Emission Point: 38088			
Height (ft.): 41	Diameter (in.): 1		
		Building: 38	
Emission Point: 48001			
Height (ft.): 38	Diameter (in.): 3		
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 48	
Emission Point: 55001			
Height (ft.): 31	Diameter (in.): 3		
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 55	
Emission Point: 55007			
Height (ft.): 13	Diameter (in.): 1		
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 55	
Emission Point: 57001			



Height (ft.): 31	Diameter (in.): 3	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 57
Emission Point: 61801		
Height (ft.): 39	Diameter (in.): 6	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 61
Emission Point: 61802		
Height (ft.): 39	Diameter (in.): 6	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 61
Emission Point: 62005		
Height (ft.): 33	Diameter (in.): 12	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 62
Emission Point: 62007		
Height (ft.): 140	Diameter (in.): 24	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 62
Emission Point: 62008		
Height (ft.): 1	Diameter (in.): 3	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 62
Emission Point: 62011		
Height (ft.): 33	Diameter (in.): 12	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 62
Emission Point: 70001		
Height (ft.): 22	Diameter (in.): 8	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 70
Emission Point: 70003		
Height (ft.): 22	Diameter (in.): 8	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 70
Emission Point: 71001		
Height (ft.): 55	Diameter (in.): 20	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 71
Emission Point: 71003		
Height (ft.): 43	Diameter (in.): 2	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 71
Emission Point: 71005		
Height (ft.): 45	Diameter (in.): 18	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 71
Emission Point: 71009		
Height (ft.): 14	Diameter (in.): 24	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 71
Emission Point: 71011		
Height (ft.): 24	Diameter (in.): 12	



	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 71
Emission Point:	71014		
	Height (ft.): 50	Diameter (in.): 2	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 71
Emission Point:	71016		
	Height (ft.): 0	Diameter (in.): 24	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 71
Emission Point:	76001		
	Height (ft.): 115	Diameter (in.): 12	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 76
Emission Point:	76004		
	Height (ft.): 1	Diameter (in.): 6	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 76
Emission Point:	76005		
	Height (ft.): 0	Diameter (in.): 6	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 76
Emission Point:	76701		
	Height (ft.): 81	Diameter (in.): 18	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 76
Emission Point:	76703		
	Height (ft.): 76	Diameter (in.): 36	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 76
Emission Point:	76705		
	Height (ft.): 76	Diameter (in.): 48	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 76
Emission Point:	76710		
	Height (ft.): 0	Diameter (in.): 24	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 76
Emission Point:	76711		
	Height (ft.): 0	Diameter (in.): 24	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 76
Emission Point:	76712		
	Height (ft.): 25	Diameter (in.): 2	
			Building: 76
Emission Point:	76713		
	Height (ft.): 25	Diameter (in.): 2	
			Building: 76
Emission Point:	76714		
	Height (ft.): 25	Diameter (in.): 2	
			Building: 76



Emission Point: 76718			
Height (ft.): 25	Diameter (in.): 2		Building: 76
Emission Point: 78001			
Height (ft.): 133	Diameter (in.): 3		
NYTMN (km.): 4741.324	NYTME (km.): 609.133		Building: 78
Emission Point: 78002			
Height (ft.): 133	Diameter (in.): 2		
NYTMN (km.): 4741.324	NYTME (km.): 609.133		Building: 78
Emission Point: 78003			
Height (ft.): 132	Diameter (in.): 16		
NYTMN (km.): 4741.324	NYTME (km.): 609.133		Building: 78
Emission Point: 78004			
Height (ft.): 132	Diameter (in.): 16		
NYTMN (km.): 4741.324	NYTME (km.): 609.133		Building: 78
Emission Point: 78005			
Height (ft.): 132	Diameter (in.): 8		
NYTMN (km.): 4741.324	NYTME (km.): 609.133		Building: 78
Emission Point: 78017			
Height (ft.): 58	Diameter (in.): 2		
NYTMN (km.): 4741.324	NYTME (km.): 609.133		Building: 78
Emission Point: 78018			
Height (ft.): 58	Diameter (in.): 2		
NYTMN (km.): 4741.324	NYTME (km.): 609.133		Building: 78
Emission Point: 78019			
Height (ft.): 50	Diameter (in.): 3		
NYTMN (km.): 4741.324	NYTME (km.): 609.133		Building: 78
Emission Point: 78025			
Height (ft.): 50	Diameter (in.): 2		
NYTMN (km.): 4741.324	NYTME (km.): 609.133		Building: 78
Emission Point: 97001			
Height (ft.): 100	Diameter (in.): 30		
NYTMN (km.): 4741.085	NYTME (km.): 609.275		Building: 96A
Emission Point: 97002			
Height (ft.): 100	Diameter (in.): 36		
NYTMN (km.): 4741.069	NYTME (km.): 609.281		Building: 96A
Emission Point: 97003			
Height (ft.): 100	Diameter (in.): 42		
NYTMN (km.): 4741.075	NYTME (km.): 609.301		Building: 96A



Item 476.2(From Mod 1):

The following emission points are included in this permit for the cited Emission Unit:

Emission Unit: C-27035

Emission Point: 27032

Height (ft.): 20 Diameter (in.): 6
NYTMN (km.): 4741.324 NYTME (km.): 609.133 Building: 27

Emission Point: 27035

Height (ft.): 21 Diameter (in.): 4
NYTMN (km.): 4741.324 NYTME (km.): 609.133 Building: 27

Emission Point: 27038

Height (ft.): 1 Diameter (in.): 1
NYTMN (km.): 4741.324 NYTME (km.): 609.133 Building: 27

Item 476.3(From Mod 1):

The following emission points are included in this permit for the cited Emission Unit:

Emission Unit: E-GNRTR

Emission Point: 28015

Height (ft.): 45 Diameter (in.): 3

Emission Point: 28016

Height (ft.): 45 Diameter (in.): 3

Emission Point: 28017

Height (ft.): 45 Diameter (in.): 3

Emission Point: 51002

Height (ft.): 13 Diameter (in.): 2

Emission Point: 51003

Height (ft.): 13 Diameter (in.): 2

Emission Point: 80001

Height (ft.): 22 Diameter (in.): 3
NYTMN (km.): 4741.324 NYTME (km.): 609.133

Emission Point: 80002

Height (ft.): 22 Diameter (in.): 2

Emission Point: 85905

Height (ft.): 23 Diameter (in.): 1

Emission Point: 86003

Height (ft.): 13 Diameter (in.): 2

Emission Point: 86004

Height (ft.): 13 Diameter (in.): 2



Emission Point: 93001
Height (ft.): 8 Diameter (in.): 2

Emission Point: 95201
Height (ft.): 8 Diameter (in.): 2

Emission Point: 95202
Height (ft.): 8 Diameter (in.): 2

Emission Point: 96001
Height (ft.): 8 Diameter (in.): 2

Emission Point: 96002
Height (ft.): 8 Diameter (in.): 2

Item 476.4(From Mod 1):

The following emission points are included in this permit for the cited Emission Unit:

Emission Unit: F-INISH

Emission Point: 24946
Height (ft.): 139 Diameter (in.): 3
NYTMN (km.): 4741.324 NYTME (km.): 609.133 Building: 24

Emission Point: 24947
Height (ft.): 71 Diameter (in.): 3
NYTMN (km.): 4741.324 NYTME (km.): 609.133 Building: 24

Emission Point: 32007
Height (ft.): 28 Diameter (in.): 27
NYTMN (km.): 4741.324 NYTME (km.): 609.133 Building: 30

Emission Point: 32008
Height (ft.): 26 Diameter (in.): 29
NYTMN (km.): 4741.324 NYTME (km.): 609.133 Building: 30

Emission Point: 32009
Height (ft.): 26 Diameter (in.): 29
NYTMN (km.): 4741.324 NYTME (km.): 609.133 Building: 30

Emission Point: 32016
Height (ft.): 26 Diameter (in.): 29
NYTMN (km.): 4741.324 NYTME (km.): 609.133 Building: 30

Emission Point: 32017
Height (ft.): 26 Diameter (in.): 29
NYTMN (km.): 4741.324 NYTME (km.): 609.133 Building: 30

Emission Point: 32026
Height (ft.): 42 Diameter (in.): 2
NYTMN (km.): 4741.324 NYTME (km.): 609.133 Building: 30

Emission Point: 32027



Height (ft.): 42	Diameter (in.): 2	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 30
Emission Point: 32028		
Height (ft.): 42	Diameter (in.): 4	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 30
Emission Point: 32040		
Height (ft.): 26	Diameter (in.): 6	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 30
Emission Point: 32042		
Height (ft.): 26	Diameter (in.): 6	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 30
Emission Point: 32044		
Height (ft.): 26	Diameter (in.): 6	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 30
Emission Point: 32046		
Height (ft.): 42	Diameter (in.): 24	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 30
Emission Point: 32049		
Height (ft.): 26	Diameter (in.): 1	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 30
Emission Point: 32050		
Height (ft.): 26	Diameter (in.): 1	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 30
Emission Point: 37016		
Height (ft.): 42	Diameter (in.): 2	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 37
Emission Point: 37059		
Height (ft.): 16	Diameter (in.): 4	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 37
Emission Point: 71013		
Height (ft.): 50	Diameter (in.): 2	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 71
Emission Point: 76006		
Height (ft.): 76	Diameter (in.): 6	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 76
Emission Point: 76007		
Height (ft.): 76	Diameter (in.): 1	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 76
Emission Point: 76716		
Height (ft.): 7	Diameter (in.): 1	



NYTMN (km.): 4741.324 NYTME (km.): 609.133 Building: 76

Emission Point: 85003
 Height (ft.): 60 Diameter (in.): 8
 NYTMN (km.): 4741.324 NYTME (km.): 609.133

Emission Point: 85006
 Height (ft.): 36 Diameter (in.): 1
 NYTMN (km.): 4741.324 NYTME (km.): 609.133 Building: 85

Emission Point: 85007
 Height (ft.): 36 Diameter (in.): 3
 Building: 85

Emission Point: 85008
 Height (ft.): 36 Diameter (in.): 3
 NYTMN (km.): 4741.324 NYTME (km.): 609.133 Building: 85

Emission Point: 85029
 Height (ft.): 36 Diameter (in.): 3
 Building: 85

Item 476.5(From Mod 1):

The following emission points are included in this permit for the cited Emission Unit:

Emission Unit: H-OFURN

Emission Point: 21012
 Height (ft.): 28 Diameter (in.): 26

Emission Point: 35027
 Height (ft.): 28 Diameter (in.): 26

Emission Point: 62016
 Height (ft.): 28 Diameter (in.): 26

Emission Point: 85063
 Height (ft.): 28 Diameter (in.): 26

Item 476.6(From Mod 1):

The following emission points are included in this permit for the cited Emission Unit:

Emission Unit: U-28002

Emission Point: 28006
 Height (ft.): 150 Diameter (in.): 71
 NYTMN (km.): 4741.324 NYTME (km.): 609.133 Building: 28

Emission Point: 28020
 Height (ft.): 50 Diameter (in.): 72
 NYTMN (km.): 4741.324 NYTME (km.): 609.133 Building: 28

Item 476.7(From Mod 0):



The following emission points are included in this permit for the cited Emission Unit:

Emission Unit: C-27018			
Emission Point:	14006		
	Height (ft.): 25	Diameter (in.): 1	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 14
Emission Point:	21011		
	Height (ft.): 37	Diameter (in.): 2	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 21
Emission Point:	22001		
	Height (ft.): 16	Diameter (in.): 8	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 22
Emission Point:	24105		
	Height (ft.): 87	Diameter (in.): 2	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 24A
Emission Point:	24207		
	Height (ft.): 118	Diameter (in.): 3	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 24
Emission Point:	24208		
	Height (ft.): 82	Diameter (in.): 2	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 24
Emission Point:	24308		
	Height (ft.): 82	Diameter (in.): 2	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 24
Emission Point:	24806		
	Height (ft.): 18	Diameter (in.): 4	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 24
Emission Point:	27022		
	Height (ft.): 20	Diameter (in.): 4	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 27
Emission Point:	27023		
	Height (ft.): 20	Diameter (in.): 4	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 27
Emission Point:	30804		
	Height (ft.): 45	Diameter (in.): 2	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 30
Emission Point:	30806		
	Height (ft.): 45	Diameter (in.): 2	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 30
Emission Point:	30807		



Height (ft.): 45	Diameter (in.): 2	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 30
Emission Point: 30808		
Height (ft.): 45	Diameter (in.): 2	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 30
Emission Point: 30904		
Height (ft.): 20	Diameter (in.): 2	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 30
Emission Point: 30914		
Height (ft.): 14	Diameter (in.): 2	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 30
Emission Point: 30916		
Height (ft.): 13	Diameter (in.): 2	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 30
Emission Point: 30917		
Height (ft.): 11	Diameter (in.): 2	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 30
Emission Point: 30918		
Height (ft.): 11	Diameter (in.): 2	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 30
Emission Point: 30921		
Height (ft.): 20	Diameter (in.): 2	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 30
Emission Point: 30922		
Height (ft.): 20	Diameter (in.): 2	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 30
Emission Point: 31002		
Height (ft.): 66	Diameter (in.): 24	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	
Emission Point: 31003		
Height (ft.): 26	Diameter (in.): 23	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 30
Emission Point: 31019		
Height (ft.): 24	Diameter (in.): 2	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 30
Emission Point: 31022		
Height (ft.): 20	Diameter (in.): 6	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 30
Emission Point: 31030		
Height (ft.): 28	Diameter (in.): 20	



	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 30E
Emission Point:	31031		
	Height (ft.): 28	Diameter (in.): 20	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 30E
Emission Point:	31032		
	Height (ft.): 10	Diameter (in.): 1	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 30E
Emission Point:	31034		
	Height (ft.): 10	Diameter (in.): 1	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 30E
Emission Point:	31036		
	Height (ft.): 46	Diameter (in.): 2	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 30E
Emission Point:	31037		
	Height (ft.): 46	Diameter (in.): 2	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 30E
Emission Point:	31040		
	Height (ft.): 45	Diameter (in.): 20	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 30
Emission Point:	31045		
	Height (ft.): 12	Diameter (in.): 1	
Emission Point:	32036		
	Height (ft.): 3	Diameter (in.): 1	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 30
Emission Point:	32038		
	Height (ft.): 9	Diameter (in.): 6	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 30
Emission Point:	34001		
	Height (ft.): 30	Diameter (in.): 2	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 34
Emission Point:	34002		
	Height (ft.): 90	Diameter (in.): 2	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 34
Emission Point:	35007		
	Height (ft.): 10	Diameter (in.): 2	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 35
Emission Point:	35009		
	Height (ft.): 41	Diameter (in.): 2	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 35



Emission Point: 35010			
Height (ft.): 20	Diameter (in.): 2		
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 35	
Emission Point: 35011			
Height (ft.): 55	Diameter (in.): 4		
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 35	
Emission Point: 35012			
Height (ft.): 40	Diameter (in.): 6		
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 35	
Emission Point: 35043			
Height (ft.): 25	Diameter (in.): 1		
		Building: 35	
Emission Point: 35044			
Height (ft.): 25	Diameter (in.): 1		
		Building: 35	
Emission Point: 35045			
Height (ft.): 25	Diameter (in.): 1		
		Building: 35	
Emission Point: 35046			
Height (ft.): 25	Diameter (in.): 1		
		Building: 35	
Emission Point: 35047			
Height (ft.): 25	Diameter (in.): 1		
		Building: 35	
Emission Point: 37002			
Height (ft.): 42	Diameter (in.): 2		
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 37	
Emission Point: 37007			
Height (ft.): 56	Diameter (in.): 2		
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 37	
Emission Point: 37011			
Height (ft.): 45	Diameter (in.): 3		
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 37	
Emission Point: 37020			
Height (ft.): 45	Diameter (in.): 3		
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 37	
Emission Point: 37022			
Height (ft.): 42	Diameter (in.): 2		
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 37	
Emission Point: 37033			



Height (ft.): 20	Diameter (in.): 1	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	
Emission Point: 37036		
Height (ft.): 20	Diameter (in.): 1	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 37
Emission Point: 37037		
Height (ft.): 7	Diameter (in.): 2	
Emission Point: 37040		
Height (ft.): 42	Diameter (in.): 2	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 37
Emission Point: 37041		
Height (ft.): 45	Diameter (in.): 4	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 37
Emission Point: 37042		
Height (ft.): 45	Diameter (in.): 2	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 37
Emission Point: 37043		
Height (ft.): 45	Diameter (in.): 2	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	
Emission Point: 37044		
Height (ft.): 45	Diameter (in.): 2	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 37
Emission Point: 37045		
Height (ft.): 45	Diameter (in.): 2	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 37
Emission Point: 37051		
Height (ft.): 45	Diameter (in.): 2	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 37
Emission Point: 37055		
Height (ft.): 44	Diameter (in.): 2	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 37
Emission Point: 37060		
Height (ft.): 0	Diameter (in.): 2	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 37
Emission Point: 37061		
Height (ft.): 45	Diameter (in.): 21	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 37
Emission Point: 37066		
Height (ft.): 38	Diameter (in.): 2	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 37



Emission Point:	37705			
Height (ft.):	43	Diameter (in.):	21	
NYTMN (km.):	4741.324	NYTME (km.):	609.133	Building: 37
Emission Point:	37707			
Height (ft.):	43	Diameter (in.):	21	
NYTMN (km.):	4741.324	NYTME (km.):	609.133	Building: 37
Emission Point:	37804			
Height (ft.):	55	Diameter (in.):	2	
NYTMN (km.):	4741.324	NYTME (km.):	609.133	Building: 37
Emission Point:	37923			
Height (ft.):	41	Diameter (in.):	2	
NYTMN (km.):	4741.324	NYTME (km.):	609.133	Building: 37
Emission Point:	37925			
Height (ft.):	15	Diameter (in.):	2	
NYTMN (km.):	4741.324	NYTME (km.):	609.133	Building: 37
Emission Point:	37930			
Height (ft.):	20	Diameter (in.):	1	
NYTMN (km.):	4741.324	NYTME (km.):	609.133	
Emission Point:	37932			
Height (ft.):	21	Diameter (in.):	1	
NYTMN (km.):	4741.324	NYTME (km.):	609.133	Building: 37
Emission Point:	38039			
Height (ft.):	12	Diameter (in.):	1	
				Building: 38
Emission Point:	57002			
Height (ft.):	70	Diameter (in.):	4	
NYTMN (km.):	4741.324	NYTME (km.):	609.133	Building: 57
Emission Point:	57003			
Height (ft.):	70	Diameter (in.):	4	
NYTMN (km.):	4741.324	NYTME (km.):	609.133	Building: 57
Emission Point:	78006			
Height (ft.):	58	Diameter (in.):	2	
NYTMN (km.):	4741.324	NYTME (km.):	609.133	Building: 78
Emission Point:	78007			
Height (ft.):	58	Diameter (in.):	2	
NYTMN (km.):	4741.324	NYTME (km.):	609.133	Building: 78
Emission Point:	78009			
Height (ft.):	24	Diameter (in.):	1	
NYTMN (km.):	4741.324	NYTME (km.):	609.133	Building: 78



Emission Point: 78011			
Height (ft.): 50	Diameter (in.): 3		
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 78	
Emission Point: 78012			
Height (ft.): 58	Diameter (in.): 2		
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 78	
Emission Point: 78015			
Height (ft.): 60	Diameter (in.): 2		
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 78	
Emission Point: 78016			
Height (ft.): 60	Diameter (in.): 2		
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 78	
Emission Point: 97053			
Height (ft.): 30	Diameter (in.): 360		
		Building: 97	

Item 476.8(From Mod 0):

The following emission points are included in this permit for the cited Emission Unit:

Emission Unit: C-61007			
Emission Point: 61001			
Height (ft.): 30	Diameter (in.): 18		
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 61	
Emission Point: 61002			
Height (ft.): 30	Diameter (in.): 18		
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 61	
Emission Point: 61003			
Height (ft.): 30	Diameter (in.): 8		
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 61	
Emission Point: 61005			
Height (ft.): 10	Diameter (in.): 6		
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 61	
Emission Point: 61006			
Height (ft.): 40	Diameter (in.): 8		
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 61	
Emission Point: 61007			
Height (ft.): 59	Diameter (in.): 8		
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 61	
Emission Point: 61008			
Height (ft.): 59	Diameter (in.): 8		
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 61	



Emission Point: 61009
 Height (ft.): 59 Diameter (in.): 8
 NYTMN (km.): 4741.324 NYTME (km.): 609.133 Building: 61

Emission Point: 61010
 Height (ft.): 59 Diameter (in.): 12
 NYTMN (km.): 4741.324 NYTME (km.): 609.133 Building: 61

Emission Point: 61805
 Height (ft.): 24 Diameter (in.): 6
 NYTMN (km.): 4741.324 NYTME (km.): 609.133 Building: 61

Item 476.9(From Mod 0):

The following emission points are included in this permit for the cited Emission Unit:

Emission Unit: C-62008

Emission Point: 55005
 Height (ft.): 75 Diameter (in.): 27
 NYTMN (km.): 4741.324 NYTME (km.): 609.133 Building: 55

Emission Point: 55006
 Height (ft.): 13 Diameter (in.): 2
 NYTMN (km.): 4741.324 NYTME (km.): 609.133 Building: 55

Emission Point: 57004
 Height (ft.): 28 Diameter (in.): 26
 NYTMN (km.): 4741.324 NYTME (km.): 609.133 Building: 57

Emission Point: 62009
 Height (ft.): 10 Diameter (in.): 2
 NYTMN (km.): 4741.324 NYTME (km.): 609.133 Building: 62

Emission Point: 62012
 Height (ft.): 31 Diameter (in.): 2
 NYTMN (km.): 4741.324 NYTME (km.): 609.133 Building: 62

Emission Point: 65001
 Height (ft.): 40 Diameter (in.): 20
 NYTMN (km.): 4741.324 NYTME (km.): 609.133 Building: 65

Item 476.10(From Mod 0):

The following emission points are included in this permit for the cited Emission Unit:

Emission Unit: C-62014

Emission Point: 68001
 Height (ft.): 110 Diameter (in.): 10
 NYTMN (km.): 4741.324 NYTME (km.): 609.133 Building: 68

Emission Point: 68002
 Height (ft.): 12 Diameter (in.): 3
 NYTMN (km.): 4741.324 NYTME (km.): 609.133 Building: 68



Emission Point: 68003
 Height (ft.): 30 Diameter (in.): 6
 NYTMN (km.): 4741.324 NYTME (km.): 609.133 Building: 68

Emission Point: 68004
 Height (ft.): 10 Diameter (in.): 6
 NYTMN (km.): 4741.324 NYTME (km.): 609.133 Building: 68

Item 476.11(From Mod 0):

The following emission points are included in this permit for the cited Emission Unit:

Emission Unit: F-INISH

Emission Point: 21101
 Height (ft.): 10 Diameter (in.): 9
 NYTMN (km.): 4741.324 NYTME (km.): 609.133 Building: 21

Emission Point: 23100
 Height (ft.): 18 Diameter (in.): 2
 NYTMN (km.): 4741.324 NYTME (km.): 609.133 Building: 23

Emission Point: 24136
 Height (ft.): 10 Diameter (in.): 2
 NYTMN (km.): 4741.324 NYTME (km.): 609.133 Building: 24

Emission Point: 24141
 Height (ft.): 0 Diameter (in.): 24
 NYTMN (km.): 4741.324 NYTME (km.): 609.133 Building: 24

Emission Point: 27102
 Height (ft.): 7 Diameter (in.): 11
 NYTMN (km.): 4741.324 NYTME (km.): 609.133 Building: 27

Emission Point: 28009
 Height (ft.): 10 Diameter (in.): 8
 NYTMN (km.): 4741.324 NYTME (km.): 609.133 Building: 28

Emission Point: 29102
 Height (ft.): 12 Diameter (in.): 6
 NYTMN (km.): 4741.324 NYTME (km.): 609.133 Building: 29

Emission Point: 30001
 Height (ft.): 35 Diameter (in.): 8
 NYTMN (km.): 4741.324 NYTME (km.): 609.133 Building: 30

Emission Point: 30002
 Height (ft.): 33 Diameter (in.): 8
 NYTMN (km.): 4741.324 NYTME (km.): 609.133 Building: 30

Emission Point: 32006
 Height (ft.): 31 Diameter (in.): 23
 NYTMN (km.): 4741.324 NYTME (km.): 609.133 Building: 30



Emission Point: 33002	Height (ft.): 28	Diameter (in.): 23	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 30
Emission Point: 33003	Height (ft.): 28	Diameter (in.): 23	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 30
Emission Point: 33004	Height (ft.): 28	Diameter (in.): 23	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 30
Emission Point: 33017	Height (ft.): 29	Diameter (in.): 2	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 30
Emission Point: 33019	Height (ft.): 26	Diameter (in.): 8	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 30
Emission Point: 33020	Height (ft.): 41	Length (in.): 11	Width (in.): 14
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 30
Emission Point: 33024	Height (ft.): 23	Diameter (in.): 3	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 30
Emission Point: 33025	Height (ft.): 38	Diameter (in.): 2	
			Building: 33
Emission Point: 33026	Height (ft.): 37	Diameter (in.): 25	
			Building: 33
Emission Point: 33901	Height (ft.): 15	Diameter (in.): 1	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 30
Emission Point: 33902	Height (ft.): 20	Diameter (in.): 1	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 30
Emission Point: 33903	Height (ft.): 15	Diameter (in.): 1	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 30
Emission Point: 33904	Height (ft.): 15	Diameter (in.): 1	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 30



Emission Point: 33905			
Height (ft.): 20	Diameter (in.): 1		
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 30	
Emission Point: 33906			
Height (ft.): 20	Diameter (in.): 1		
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 30	
Emission Point: 37001			
Height (ft.): 42	Diameter (in.): 2		
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 37	
Emission Point: 37032			
Height (ft.): 25	Diameter (in.): 1		
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 37	
Emission Point: 37047			
Height (ft.): 42	Diameter (in.): 2		
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 37	
Emission Point: 37049			
Height (ft.): 42	Diameter (in.): 2		
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 37	
Emission Point: 37050			
Height (ft.): 42	Diameter (in.): 2		
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 37	
Emission Point: 37054			
Height (ft.): 40	Diameter (in.): 1		
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 37	
Emission Point: 37701			
Height (ft.): 43	Diameter (in.): 8		
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 37	
Emission Point: 37924			
Height (ft.): 15	Diameter (in.): 2		
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 37	
Emission Point: 37948			
Height (ft.): 0	Diameter (in.): 24		
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 37	
Emission Point: 37960			
Height (ft.): 62	Diameter (in.): 4		
		Building: 37	
Emission Point: 41001			
Height (ft.): 23	Diameter (in.): 2		
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 41	
Emission Point: 41002			



Height (ft.): 22	Diameter (in.): 2	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 41
Emission Point: 41003		
Height (ft.): 30	Diameter (in.): 8	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 41
Emission Point: 42001		
Height (ft.): 32	Diameter (in.): 14	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 42
Emission Point: 42002		
Height (ft.): 32	Diameter (in.): 14	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 42
Emission Point: 42003		
Height (ft.): 32	Diameter (in.): 14	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 42
Emission Point: 42005		
Height (ft.): 4	Diameter (in.): 36	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 42
Emission Point: 42012		
Height (ft.): 30	Diameter (in.): 40	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 42A
Emission Point: 42013		
Height (ft.): 4	Diameter (in.): 3	
Emission Point: 42019		
Height (ft.): 34	Diameter (in.): 1	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 42
Emission Point: 42020		
Height (ft.): 34	Diameter (in.): 1	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 42
Emission Point: 61602		
Height (ft.): 20	Diameter (in.): 8	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 61
Emission Point: 61603		
Height (ft.): 35	Diameter (in.): 6	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 61
Emission Point: 71010		
Height (ft.): 12	Diameter (in.): 12	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 71
Emission Point: 78021		
Height (ft.): 11	Diameter (in.): 1	
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 78



Emission Point: 78022	Height (ft.): 15	Diameter (in.): 1	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 78
Emission Point: 78023	Height (ft.): 15	Diameter (in.): 1	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 78
Emission Point: 78024	Height (ft.): 10	Diameter (in.): 1	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 78
Emission Point: 85002	Height (ft.): 105	Diameter (in.): 24	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 85
Emission Point: 85004	Height (ft.): 107	Diameter (in.): 2	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 85
Emission Point: 85013	Height (ft.): 105	Diameter (in.): 2	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 85
Emission Point: 85020	Height (ft.): 16	Diameter (in.): 1	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 85
Emission Point: 85021	Height (ft.): 56	Diameter (in.): 1	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 85
Emission Point: 85022	Height (ft.): 16	Diameter (in.): 1	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 85
Emission Point: 85023	Height (ft.): 42	Diameter (in.): 0	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 85
Emission Point: 85024	Height (ft.): 51	Diameter (in.): 0	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 85
Emission Point: 85032	Height (ft.): 20	Diameter (in.): 1	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 85
Emission Point: 85036	Height (ft.): 30	Diameter (in.): 1	
	NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 85



Emission Point: 85037			
Height (ft.): 30	Diameter (in.): 1		
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 85	
Emission Point: 85038			
Height (ft.): 30	Diameter (in.): 1		
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 85	
Emission Point: 85039			
Height (ft.): 30	Diameter (in.): 1		
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 85	
Emission Point: 85040			
Height (ft.): 30	Diameter (in.): 1		
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 85	
Emission Point: 85041			
Height (ft.): 30	Diameter (in.): 1		
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 85	
Emission Point: 85042			
Height (ft.): 30	Diameter (in.): 1		
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 85	
Emission Point: 85045			
Height (ft.): 30	Diameter (in.): 1		
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 85	
Emission Point: 85046			
Height (ft.): 30	Diameter (in.): 8		
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 85	
Emission Point: 85054			
Height (ft.): 10	Diameter (in.): 8		
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 85	
Emission Point: 85058			
Height (ft.): 30	Diameter (in.): 1		
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 85	
Emission Point: 85059			
Height (ft.): 16	Diameter (in.): 8		
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 85	
Emission Point: 85066			
Height (ft.): 100	Diameter (in.): 2		
NYTMN (km.): 4741.324	NYTME (km.): 609.133	Building: 85	
Emission Point: 85067			
Height (ft.): 25	Diameter (in.): 2		
		Building: 85	
Emission Point: 85903			



Emission Unit: W-97004

Emission Point: 95002
 Height (ft.): 27 Diameter (in.): 36
 NYTMN (km.): 4741.324 NYTME (km.): 609.133 Building: 95

Emission Point: 97004
 Height (ft.): 15 Diameter (in.): 6
 NYTMN (km.): 4741.324 NYTME (km.): 609.133 Building: 97

Emission Point: 97005
 Height (ft.): 15 Diameter (in.): 6
 NYTMN (km.): 4741.324 NYTME (km.): 609.133 Building: 97

Emission Point: 97008
 Height (ft.): 24 Diameter (in.): 4
 NYTMN (km.): 4741.324 NYTME (km.): 609.133 Building: 97

Emission Point: 97011
 Height (ft.): 15 Diameter (in.): 3
 NYTMN (km.): 4741.324 NYTME (km.): 609.133 Building: 97

Emission Point: 97012
 Height (ft.): 15 Diameter (in.): 3
 NYTMN (km.): 4741.324 NYTME (km.): 609.133 Building: 97

Emission Point: 97017
 Height (ft.): 15 Diameter (in.): 8
 NYTMN (km.): 4741.324 NYTME (km.): 609.133 Building: 96A

Emission Point: 97020
 Height (ft.): 15 Diameter (in.): 2
 NYTMN (km.): 4741.324 NYTME (km.): 609.133 Building: 97

Emission Point: 97021
 Height (ft.): 15 Diameter (in.): 2
 NYTMN (km.): 4741.324 NYTME (km.): 609.133 Building: 97

Emission Point: 97041
 Height (ft.): 15 Diameter (in.): 1
 NYTMN (km.): 4741.324 NYTME (km.): 609.133 Building: 97

Emission Point: 97042
 Height (ft.): 36 Diameter (in.): 2
 NYTMN (km.): 4741.324 NYTME (km.): 609.133 Building: 97

Emission Point: 97043
 Height (ft.): 36 Diameter (in.): 2
 NYTMN (km.): 4741.324 NYTME (km.): 609.133 Building: 97

Emission Point: 97047
 Height (ft.): 25 Diameter (in.): 240



Emission Point: 97048
Height (ft.): 30 Diameter (in.): 1344

Emission Point: 97049
Height (ft.): 30 Diameter (in.): 1344

Condition 477: Process Definition By Emission Unit
Effective between the dates of 01/07/2008 and Permit Expiration Date

Applicable Federal Requirement:6NYCRR 201-6

Item 477.1(From Mod 1):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018
Process: 013 Source Classification Code: 3-01-999-99

Process Description:
Equipment for Family of Material #013, which is a
miscellaneous organic manufacturing unit (MCPU) that is
regulated under 40 CFR Part 63, Subpart FFFF.

Emission Source/Control: 76EAS - Control
Control Type: GAS SCRUBBER (GENERAL, NOT CLASSIFIED)

Emission Source/Control: 76ESC - Control
Control Type: FABRIC FILTER

Emission Source/Control: 76EWS - Control
Control Type: VENTURI SCRUBBER

Emission Source/Control: 76WAS - Control
Control Type: GAS SCRUBBER (GENERAL, NOT CLASSIFIED)

Emission Source/Control: 76WSC - Control
Control Type: FABRIC FILTER

Emission Source/Control: 76ACW - Process

Emission Source/Control: 76CH1 - Process

Emission Source/Control: 76CH2 - Process

Emission Source/Control: 76DV1 - Process

Emission Source/Control: 76DV2 - Process

Emission Source/Control: 76DV3 - Process

Emission Source/Control: 76EFK - Process

Emission Source/Control: 76EHC - Process

Emission Source/Control: 76EHW - Process



Emission Source/Control: 76EHY - Process

Emission Source/Control: 76EPT - Process

Emission Source/Control: 76ERC - Process

Emission Source/Control: 76ESB - Process

Emission Source/Control: 76FP1 - Process

Emission Source/Control: 76FP2 - Process

Emission Source/Control: 76HT6 - Process

Emission Source/Control: 76PBT - Process

Emission Source/Control: 76SBS - Process

Emission Source/Control: 76SPK - Process

Emission Source/Control: 76WFK - Process

Emission Source/Control: 76WHC - Process

Emission Source/Control: 76WHR - Process

Emission Source/Control: 76WHW - Process

Emission Source/Control: 76WHY - Process

Emission Source/Control: 76WPT - Process

Emission Source/Control: 76WSB - Process

Emission Source/Control: 76WSW - Process

Item 477.2(From Mod 1):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 022

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #022, which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63, Subpart FFFF.

Emission Source/Control: 76EAS - Control

Control Type: GAS SCRUBBER (GENERAL, NOT CLASSIFIED)

Emission Source/Control: 76ESC - Control

Control Type: FABRIC FILTER



Emission Source/Control: 76EWS - Control
Control Type: VENTURI SCRUBBER

Emission Source/Control: 76WAS - Control
Control Type: GAS SCRUBBER (GENERAL, NOT CLASSIFIED)

Emission Source/Control: 76WSC - Control
Control Type: FABRIC FILTER

Emission Source/Control: 76ACW - Process

Emission Source/Control: 76CH1 - Process

Emission Source/Control: 76CH2 - Process

Emission Source/Control: 76DV1 - Process

Emission Source/Control: 76DV2 - Process

Emission Source/Control: 76DV3 - Process

Emission Source/Control: 76EFK - Process

Emission Source/Control: 76EHC - Process

Emission Source/Control: 76EHW - Process

Emission Source/Control: 76EHY - Process

Emission Source/Control: 76EPT - Process

Emission Source/Control: 76ERC - Process

Emission Source/Control: 76ESB - Process

Emission Source/Control: 76FP1 - Process

Emission Source/Control: 76PBT - Process

Emission Source/Control: 76SBS - Process

Emission Source/Control: 76WFK - Process

Emission Source/Control: 76WHC - Process

Emission Source/Control: 76WHR - Process

Emission Source/Control: 76WHW - Process

Emission Source/Control: 76WHY - Process

Emission Source/Control: 76WPT - Process



Emission Source/Control: 76WSB - Process

Emission Source/Control: 76WSW - Process

Item 477.3(From Mod 1):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 040

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #040 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63, Subpart FFFF.

Emission Source/Control: 76EWS - Control
Control Type: VENTURI SCRUBBER

Emission Source/Control: 76WSC - Control
Control Type: FABRIC FILTER

Emission Source/Control: 76ACW - Process

Emission Source/Control: 76CH2 - Process

Emission Source/Control: 76DV1 - Process

Emission Source/Control: 76DV2 - Process

Emission Source/Control: 76DV3 - Process

Emission Source/Control: 76FP2 - Process

Emission Source/Control: 76PBT - Process

Emission Source/Control: 76SBS - Process

Emission Source/Control: 76WFK - Process

Emission Source/Control: 76WHC - Process

Emission Source/Control: 76WHR - Process

Emission Source/Control: 76WHW - Process

Emission Source/Control: 76WPT - Process

Emission Source/Control: 76WSB - Process

Emission Source/Control: 76WSW - Process

Item 477.4(From Mod 1):

This permit authorizes the following regulated processes for the cited Emission Unit:



Emission Unit: C-27018

Process: 047

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #047 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63, Subpart FFFF. This process operates out of buildings 71 and 76.

Emission Source/Control: 71HYS - Control

Control Type: WET SCRUBBER

Emission Source/Control: 76EAS - Control

Control Type: GAS SCRUBBER (GENERAL, NOT CLASSIFIED)

Emission Source/Control: 76ESC - Control

Control Type: FABRIC FILTER

Emission Source/Control: 76EWS - Control

Control Type: VENTURI SCRUBBER

Emission Source/Control: 76WSC - Control

Control Type: FABRIC FILTER

Emission Source/Control: 71CR2 - Process

Emission Source/Control: 71CR7 - Process

Emission Source/Control: 71DS3 - Process

Emission Source/Control: 71FP1 - Process

Emission Source/Control: 71FP3 - Process

Emission Source/Control: 71H2R - Process

Emission Source/Control: 71HES - Process

Emission Source/Control: 71HY3 - Process

Emission Source/Control: 71SIL - Process

Emission Source/Control: 71SWT - Process

Emission Source/Control: 71VAC - Process

Emission Source/Control: 76ACW - Process

Emission Source/Control: 76CH1 - Process

Emission Source/Control: 76CH2 - Process

Emission Source/Control: 76DV1 - Process



Emission Source/Control: 76DV2 - Process
Emission Source/Control: 76DV3 - Process
Emission Source/Control: 76EFK - Process
Emission Source/Control: 76EHC - Process
Emission Source/Control: 76EHW - Process
Emission Source/Control: 76EHY - Process
Emission Source/Control: 76EPT - Process
Emission Source/Control: 76ERC - Process
Emission Source/Control: 76ESB - Process
Emission Source/Control: 76FP1 - Process
Emission Source/Control: 76FP2 - Process
Emission Source/Control: 76PBT - Process
Emission Source/Control: 76SBS - Process
Emission Source/Control: 76WFK - Process
Emission Source/Control: 76WHC - Process
Emission Source/Control: 76WHR - Process
Emission Source/Control: 76WHW - Process
Emission Source/Control: 76WHY - Process
Emission Source/Control: 76WPT - Process
Emission Source/Control: 76WSB - Process
Emission Source/Control: 76WSW - Process

Item 477.5(From Mod 1):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 066

Source Classification Code: 3-01-026-30

Process Description:

Equipment for Family of Material #066 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF. This process operates out of buildings 76 and 78.



Emission Source/Control: 76EAS - Control
Control Type: GAS SCRUBBER (GENERAL, NOT CLASSIFIED)

Emission Source/Control: 76ESC - Control
Control Type: FABRIC FILTER

Emission Source/Control: 76EWS - Control
Control Type: VENTURI SCRUBBER

Emission Source/Control: 76WSC - Control
Control Type: FABRIC FILTER

Emission Source/Control: 78FCB - Control
Control Type: FABRIC FILTER

Emission Source/Control: 76ACW - Process

Emission Source/Control: 76CH1 - Process

Emission Source/Control: 76CH2 - Process

Emission Source/Control: 76DV1 - Process

Emission Source/Control: 76DV2 - Process

Emission Source/Control: 76DV3 - Process

Emission Source/Control: 76EFK - Process

Emission Source/Control: 76EHC - Process

Emission Source/Control: 76EHW - Process

Emission Source/Control: 76EHY - Process

Emission Source/Control: 76EPT - Process

Emission Source/Control: 76ERC - Process

Emission Source/Control: 76ESB - Process

Emission Source/Control: 76FP1 - Process

Emission Source/Control: 76FP2 - Process

Emission Source/Control: 76PBT - Process

Emission Source/Control: 76SBS - Process

Emission Source/Control: 76WFK - Process

Emission Source/Control: 76WHC - Process



Emission Source/Control: 76WHR - Process
Emission Source/Control: 76WHW - Process
Emission Source/Control: 76WHY - Process
Emission Source/Control: 76WPT - Process
Emission Source/Control: 76WSB - Process
Emission Source/Control: 76WSW - Process
Emission Source/Control: 78BUH - Process
Emission Source/Control: 78DME - Process
Emission Source/Control: 78FDM - Process
Emission Source/Control: 78FEH - Process
Emission Source/Control: 78FSC - Process

Item 477.6(From Mod 1):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 067

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #067 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF. This process operates out of buildings 27, 35 and 70.

Emission Source/Control: 27HCS - Control
Control Type: PACKED-GAS ABSORPTION SYSTEM

Emission Source/Control: 35CV7 - Control
Control Type: CONSERVATION VENT

Emission Source/Control: 35CV8 - Control
Control Type: CONSERVATION VENT

Emission Source/Control: 35PGA - Control
Control Type: PACKED-GAS ABSORPTION SYSTEM

Emission Source/Control: 35VGS - Control
Control Type: VENTURI SCRUBBER

Emission Source/Control: 27GDH - Process

Emission Source/Control: 35B51 - Process

Emission Source/Control: 35FSV - Process



Emission Source/Control: 35NE1 - Process

Emission Source/Control: 35NE2 - Process

Emission Source/Control: 38539 - Process

Emission Source/Control: 38ST7 - Process

Emission Source/Control: 38ST8 - Process

Emission Source/Control: 70HTE - Process

Emission Source/Control: 70HTW - Process

Item 477.7(From Mod 1):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 068

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #068 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF. This process operates out of buildings 71 and 76.

Emission Source/Control: 71HYS - Control

Control Type: WET SCRUBBER

Emission Source/Control: 76EAS - Control

Control Type: GAS SCRUBBER (GENERAL, NOT CLASSIFIED)

Emission Source/Control: 76ESC - Control

Control Type: FABRIC FILTER

Emission Source/Control: 76EWS - Control

Control Type: VENTURI SCRUBBER

Emission Source/Control: 76WAS - Control

Control Type: GAS SCRUBBER (GENERAL, NOT CLASSIFIED)

Emission Source/Control: 76WSC - Control

Control Type: FABRIC FILTER

Emission Source/Control: 71CR1 - Process

Emission Source/Control: 71CR2 - Process

Emission Source/Control: 71CR5 - Process

Emission Source/Control: 71CR7 - Process

Emission Source/Control: 71CR8 - Process



Emission Source/Control: 71DS3 - Process

Emission Source/Control: 71FP1 - Process

Emission Source/Control: 71FP3 - Process

Emission Source/Control: 71H2R - Process

Emission Source/Control: 71HES - Process

Emission Source/Control: 71HY3 - Process

Emission Source/Control: 71RT1 - Process

Emission Source/Control: 71RT2 - Process

Emission Source/Control: 71SIL - Process

Emission Source/Control: 71SWT - Process

Emission Source/Control: 71VAC - Process

Emission Source/Control: 71WT7 - Process

Emission Source/Control: 76ACW - Process

Emission Source/Control: 76CH1 - Process

Emission Source/Control: 76CH2 - Process

Emission Source/Control: 76DV1 - Process

Emission Source/Control: 76DV2 - Process

Emission Source/Control: 76DV3 - Process

Emission Source/Control: 76EFK - Process

Emission Source/Control: 76EHC - Process

Emission Source/Control: 76EHW - Process

Emission Source/Control: 76EHY - Process

Emission Source/Control: 76EPT - Process

Emission Source/Control: 76ERC - Process

Emission Source/Control: 76ESB - Process

Emission Source/Control: 76FP1 - Process



Emission Source/Control: 76FP2 - Process
Emission Source/Control: 76PBT - Process
Emission Source/Control: 76SBS - Process
Emission Source/Control: 76SPK - Process
Emission Source/Control: 76TRB - Process
Emission Source/Control: 76WFK - Process
Emission Source/Control: 76WHC - Process
Emission Source/Control: 76WHR - Process
Emission Source/Control: 76WHW - Process
Emission Source/Control: 76WHY - Process
Emission Source/Control: 76WPT - Process
Emission Source/Control: 76WSB - Process
Emission Source/Control: 76WSW - Process

Item 477.8(From Mod 1):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018
Process: 071 Source Classification Code: 3-01-999-99
Process Description:
Equipment for Family of Material #071 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF.

Emission Source/Control: 23SCR - Control
Control Type: WET SCRUBBER

Emission Source/Control: 24HLS - Control
Control Type: WET SCRUBBER

Emission Source/Control: 23TK4 - Process

Emission Source/Control: 23TK5 - Process

Emission Source/Control: 23TK7 - Process

Emission Source/Control: 23TKA - Process

Emission Source/Control: 23TKC - Process

Emission Source/Control: 24ANE - Process



Emission Source/Control: 24CHL - Process

Emission Source/Control: 24CHT - Process

Emission Source/Control: 24FTO - Process

Emission Source/Control: 24HT1 - Process

Emission Source/Control: 24HT2 - Process

Emission Source/Control: 24HT4 - Process

Emission Source/Control: 24HTS - Process

Emission Source/Control: 24NO1 - Process

Emission Source/Control: 24PRT - Process

Emission Source/Control: 24SIL - Process

Emission Source/Control: 24SOX - Process

Emission Source/Control: 24T12 - Process

Item 477.9(From Mod 1):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 080

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #080 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF. This process operates out of buildings 23, 24, 24A and 71.

Emission Source/Control: 23SCR - Control

Control Type: WET SCRUBBER

Emission Source/Control: 24AVR - Control

Control Type: VAPOR RECOVERY SYS(INCL.
CONDENSERS,HOODING, OTHER ENCLOSURES)

Emission Source/Control: 24GBF - Control

Control Type: GRAVEL BED FILTER

Emission Source/Control: FBCS1 - Control

Control Type: PACKED-GAS ABSORPTION SYSTEM

Emission Source/Control: FBCS2 - Control

Control Type: PACKED-GAS ABSORPTION SYSTEM

Emission Source/Control: FBIAB - Control



Control Type: DIRECT FLAME AFTERBURNER

Emission Source/Control: FBIQU - Control
Control Type: SPRAY TOWER

Emission Source/Control: IWS11 - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS12 - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS1A - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS1B - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS1C - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS21 - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS22 - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS2A - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS2B - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS2C - Control
Control Type: WET SCRUBBER

Emission Source/Control: RKIAB - Control
Control Type: DIRECT FLAME AFTERBURNER

Emission Source/Control: RKICS - Control
Control Type: PACKED-GAS ABSORPTION SYSTEM

Emission Source/Control: RKIQU - Control
Control Type: SPRAY TOWER

Emission Source/Control: 23BLK - Process

Emission Source/Control: 23SST - Process

Emission Source/Control: 24ACD - Process

Emission Source/Control: 24ANE - Process

Emission Source/Control: 24ATK - Process



Emission Source/Control: 24BKC - Process

Emission Source/Control: 24BKR - Process

Emission Source/Control: 24DIC - Process

Emission Source/Control: 24ENZ - Process

Emission Source/Control: 24FAH - Process

Emission Source/Control: 24FAK - Process

Emission Source/Control: 24HYD - Process

Emission Source/Control: 24KOH - Process

Emission Source/Control: 24PBT - Process

Emission Source/Control: 24PRE - Process

Emission Source/Control: 24PSS - Process

Emission Source/Control: 24RST - Process

Emission Source/Control: 24SIW - Process

Emission Source/Control: 24SOX - Process

Emission Source/Control: 24ST1 - Process

Emission Source/Control: 24ST2 - Process

Emission Source/Control: 24ST3 - Process

Emission Source/Control: 24ST4 - Process

Emission Source/Control: 24WSH - Process

Emission Source/Control: 24XST - Process

Emission Source/Control: MTCSS - Process

Emission Source/Control: WTVST - Process

Item 477.10(From Mod 1):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 082

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #082 which is a miscellaneous organic manufacturing unit (MCPU) that is



regulated under 40 CFR Part 63 Subpart FFFF. This process operates out of buildings 23, 24 and 24A.

Emission Source/Control: 24PGA - Control
Control Type: PACKED-GAS ABSORPTION SYSTEM

Emission Source/Control: FBCS1 - Control
Control Type: PACKED-GAS ABSORPTION SYSTEM

Emission Source/Control: FBCS2 - Control
Control Type: PACKED-GAS ABSORPTION SYSTEM

Emission Source/Control: FBIAB - Control
Control Type: DIRECT FLAME AFTERBURNER

Emission Source/Control: FBIQU - Control
Control Type: SPRAY TOWER

Emission Source/Control: IWS11 - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS12 - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS1A - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS1B - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS1C - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS21 - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS22 - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS2A - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS2B - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS2C - Control
Control Type: WET SCRUBBER

Emission Source/Control: RKIAB - Control
Control Type: DIRECT FLAME AFTERBURNER

Emission Source/Control: RKICS - Control
Control Type: PACKED-GAS ABSORPTION SYSTEM



Emission Source/Control: RKIQU - Control
Control Type: SPRAY TOWER

Emission Source/Control: 23TKC - Process

Emission Source/Control: 24AID - Process

Emission Source/Control: 24ANE - Process

Emission Source/Control: 24ART - Process

Emission Source/Control: 24BD1 - Process

Emission Source/Control: 24BD2 - Process

Emission Source/Control: 24BLK - Process

Emission Source/Control: 24BR2 - Process

Emission Source/Control: 24FK4 - Process

Emission Source/Control: 24FOK - Process

Emission Source/Control: 24HCO - Process

Emission Source/Control: 24N12 - Process

Emission Source/Control: 24NO5 - Process

Emission Source/Control: 24PCT - Process

Emission Source/Control: 24SF1 - Process

Emission Source/Control: 24SF2 - Process

Emission Source/Control: 24SHT - Process

Emission Source/Control: 24SOU - Process

Emission Source/Control: 24SOX - Process

Emission Source/Control: 24SRA - Process

Emission Source/Control: 24WST - Process

Emission Source/Control: 24WTA - Process

Item 477.11(From Mod 1):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 083

Source Classification Code: 3-01-999-99



Process Description:

Equipment for Family of Material #083 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF.

Emission Source/Control: 23SCR - Control
Control Type: WET SCRUBBER

Emission Source/Control: FBCS1 - Control
Control Type: PACKED-GAS ABSORPTION SYSTEM

Emission Source/Control: FBCS2 - Control
Control Type: PACKED-GAS ABSORPTION SYSTEM

Emission Source/Control: FBIAB - Control
Control Type: DIRECT FLAME AFTERBURNER

Emission Source/Control: FBIQU - Control
Control Type: SPRAY TOWER

Emission Source/Control: IWS11 - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS12 - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS1A - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS1B - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS1C - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS21 - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS22 - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS2A - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS2B - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS2C - Control
Control Type: WET SCRUBBER

Emission Source/Control: RKIAB - Control
Control Type: DIRECT FLAME AFTERBURNER



Emission Source/Control: RKICS - Control
Control Type: PACKED-GAS ABSORPTION SYSTEM

Emission Source/Control: RKIQU - Control
Control Type: SPRAY TOWER

Emission Source/Control: 23BT1 - Process

Emission Source/Control: 23BT2 - Process

Emission Source/Control: 23BT3 - Process

Emission Source/Control: 23DHV - Process

Emission Source/Control: 23HT1 - Process

Emission Source/Control: 23HT2 - Process

Emission Source/Control: 23HT3 - Process

Emission Source/Control: 23HT4 - Process

Emission Source/Control: 23HT5 - Process

Emission Source/Control: 23HT6 - Process

Emission Source/Control: 23HT7 - Process

Emission Source/Control: 23TKC - Process

Emission Source/Control: 24ANE - Process

Emission Source/Control: 24SOX - Process

Item 477.12(From Mod 1):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 085

Source Classification Code: 3-01-999-99

Process Description:

This process represents FOM 085, which is a miscellaneous organic chemical manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF.

Emission Source/Control: 76EWS - Control
Control Type: VENTURI SCRUBBER

Emission Source/Control: 76WAS - Control
Control Type: GAS SCRUBBER (GENERAL, NOT CLASSIFIED)

Emission Source/Control: 76SBS - Process

Emission Source/Control: 76WFK - Process



Emission Source/Control: 76WHC - Process

Emission Source/Control: 76WHR - Process

Emission Source/Control: 76WHW - Process

Emission Source/Control: 76WHY - Process

Emission Source/Control: 76WSB - Process

Emission Source/Control: 76WSW - Process

Item 477.13(From Mod 1):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 089

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #089 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF. This process operates out of buildings 23, 24 and 24A.

Emission Source/Control: 23SCR - Control

Control Type: WET SCRUBBER

Emission Source/Control: FBCS1 - Control

Control Type: PACKED-GAS ABSORPTION SYSTEM

Emission Source/Control: FBCS2 - Control

Control Type: PACKED-GAS ABSORPTION SYSTEM

Emission Source/Control: FBIAB - Control

Control Type: DIRECT FLAME AFTERBURNER

Emission Source/Control: FBIQU - Control

Control Type: SPRAY TOWER

Emission Source/Control: IWS11 - Control

Control Type: WET SCRUBBER

Emission Source/Control: IWS12 - Control

Control Type: WET SCRUBBER

Emission Source/Control: IWS1A - Control

Control Type: WET SCRUBBER

Emission Source/Control: IWS1B - Control

Control Type: WET SCRUBBER

Emission Source/Control: IWS1C - Control

Control Type: WET SCRUBBER



Emission Source/Control: IWS21 - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS22 - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS2A - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS2B - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS2C - Control
Control Type: WET SCRUBBER

Emission Source/Control: RKIAB - Control
Control Type: DIRECT FLAME AFTERBURNER

Emission Source/Control: RKICS - Control
Control Type: PACKED-GAS ABSORPTION SYSTEM

Emission Source/Control: RKIQU - Control
Control Type: SPRAY TOWER

Emission Source/Control: 23BT1 - Process

Emission Source/Control: 23BT2 - Process

Emission Source/Control: 23BT3 - Process

Emission Source/Control: 23DHV - Process

Emission Source/Control: 23HT1 - Process

Emission Source/Control: 23HT2 - Process

Emission Source/Control: 23HT3 - Process

Emission Source/Control: 23HT4 - Process

Emission Source/Control: 23HT5 - Process

Emission Source/Control: 23HT6 - Process

Emission Source/Control: 23HT7 - Process

Emission Source/Control: 23TKC - Process

Emission Source/Control: 24ANE - Process

Emission Source/Control: 24SOX - Process



Item 477.14(From Mod 1):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 090

Source Classification Code: 3-01-999-99

Process Description:

This process represents FOM 090, which is a miscellaneous organic chemical manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF. This process operates out of buildings 61 and 62.

Emission Source/Control: 57BH1 - Control

Control Type: FABRIC FILTER

Emission Source/Control: 57BH2 - Control

Control Type: FABRIC FILTER

Emission Source/Control: 61FS1 - Control

Control Type: WET SCRUBBER

Emission Source/Control: 61FS2 - Control

Control Type: WET SCRUBBER

Emission Source/Control: 622CC - Control

Control Type: VAPOR RECOVERY SYS(INCL.
CONDENSERS,HOODING, OTHER ENCLOSURES)

Emission Source/Control: 622VC - Control

Control Type: VAPOR RECOVERY SYS(INCL.
CONDENSERS,HOODING, OTHER ENCLOSURES)

Emission Source/Control: 623CC - Control

Control Type: VAPOR RECOVERY SYS(INCL.
CONDENSERS,HOODING, OTHER ENCLOSURES)

Emission Source/Control: 623VC - Control

Control Type: VAPOR RECOVERY SYS(INCL.
CONDENSERS,HOODING, OTHER ENCLOSURES)

Emission Source/Control: 62EST - Control

Control Type: SPRAY TOWER

Emission Source/Control: 62EVS - Control

Control Type: VENTURI SCRUBBER

Emission Source/Control: 62RGC - Control

Control Type: VAPOR RECOVERY SYS(INCL.
CONDENSERS,HOODING, OTHER ENCLOSURES)

Emission Source/Control: 62WST - Control

Control Type: SPRAY TOWER

Emission Source/Control: 62WVS - Control



Control Type: VENTURI SCRUBBER

Emission Source/Control: FBCS1 - Control
Control Type: PACKED-GAS ABSORPTION SYSTEM

Emission Source/Control: FBCS2 - Control
Control Type: PACKED-GAS ABSORPTION SYSTEM

Emission Source/Control: FBIAB - Control
Control Type: DIRECT FLAME AFTERBURNER

Emission Source/Control: FBIQU - Control
Control Type: SPRAY TOWER

Emission Source/Control: IWS11 - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS12 - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS1A - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS1B - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS1C - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS21 - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS22 - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS2A - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS2B - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS2C - Control
Control Type: WET SCRUBBER

Emission Source/Control: M4CCS - Control
Control Type: VAPOR RECOVERY SYS(INCL.
CONDENSERS,HOODING, OTHER ENCLOSURES)

Emission Source/Control: M4VCS - Control
Control Type: VAPOR RECOVERY SYS(INCL.
CONDENSERS,HOODING, OTHER ENCLOSURES)

Emission Source/Control: MCSVI - Control



Control Type: DIRECT FLAME AFTERBURNER

Emission Source/Control: MCSVS - Control
Control Type: WET SCRUBBER

Emission Source/Control: RKIAB - Control
Control Type: DIRECT FLAME AFTERBURNER

Emission Source/Control: RKICS - Control
Control Type: PACKED-GAS ABSORPTION SYSTEM

Emission Source/Control: RKIQU - Control
Control Type: SPRAY TOWER

Emission Source/Control: 024TK - Process

Emission Source/Control: 101CO - Process

Emission Source/Control: 110CO - Process

Emission Source/Control: 112AB - Process

Emission Source/Control: 113AB - Process

Emission Source/Control: 113CC - Process

Emission Source/Control: 114AC - Process

Emission Source/Control: 114BC - Process

Emission Source/Control: 116AB - Process

Emission Source/Control: 119CO - Process

Emission Source/Control: 55CFH - Process

Emission Source/Control: 564AT - Process

Emission Source/Control: 57CFH - Process

Emission Source/Control: 61NMS - Process

Emission Source/Control: 61SMS - Process

Emission Source/Control: 6204A - Process

Emission Source/Control: 6256T - Process

Emission Source/Control: 62CST - Process

Emission Source/Control: 62FH1 - Process

Emission Source/Control: 62FH2 - Process



Emission Source/Control: 62GWV - Process
Emission Source/Control: 62H2O - Process
Emission Source/Control: 62MCT - Process
Emission Source/Control: 62PUR - Process
Emission Source/Control: 62RC2 - Process
Emission Source/Control: 62RC3 - Process
Emission Source/Control: 62RCL - Process
Emission Source/Control: 62RP2 - Process
Emission Source/Control: 62RP3 - Process
Emission Source/Control: 62RP4 - Process
Emission Source/Control: 62RRE - Process
Emission Source/Control: 62SC2 - Process
Emission Source/Control: 62SC3 - Process
Emission Source/Control: 62SC4 - Process
Emission Source/Control: 62SP2 - Process
Emission Source/Control: 62SP3 - Process
Emission Source/Control: 62SP4 - Process
Emission Source/Control: 62T12 - Process
Emission Source/Control: 62T56 - Process
Emission Source/Control: 62T59 - Process
Emission Source/Control: 62TAB - Process
Emission Source/Control: 62TBA - Process
Emission Source/Control: 62VTS - Process
Emission Source/Control: M4MRC - Process
Emission Source/Control: SSTVT - Process
Emission Source/Control: T506D - Process



Emission Source/Control: TRIST - Process

Item 477.15(From Mod 1):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 093

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #093 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF.

Emission Source/Control: 23SCR - Control

Control Type: WET SCRUBBER

Emission Source/Control: FBCS1 - Control

Control Type: PACKED-GAS ABSORPTION SYSTEM

Emission Source/Control: FBCS2 - Control

Control Type: PACKED-GAS ABSORPTION SYSTEM

Emission Source/Control: FBIAB - Control

Control Type: DIRECT FLAME AFTERBURNER

Emission Source/Control: FBIQU - Control

Control Type: SPRAY TOWER

Emission Source/Control: IWS11 - Control

Control Type: WET SCRUBBER

Emission Source/Control: IWS12 - Control

Control Type: WET SCRUBBER

Emission Source/Control: IWS1A - Control

Control Type: WET SCRUBBER

Emission Source/Control: IWS1B - Control

Control Type: WET SCRUBBER

Emission Source/Control: IWS1C - Control

Control Type: WET SCRUBBER

Emission Source/Control: IWS21 - Control

Control Type: WET SCRUBBER

Emission Source/Control: IWS22 - Control

Control Type: WET SCRUBBER

Emission Source/Control: IWS2A - Control

Control Type: WET SCRUBBER

Emission Source/Control: IWS2B - Control

Control Type: WET SCRUBBER



Emission Source/Control: IWS2C - Control
Control Type: WET SCRUBBER

Emission Source/Control: RKIAB - Control
Control Type: DIRECT FLAME AFTERBURNER

Emission Source/Control: RKICS - Control
Control Type: PACKED-GAS ABSORPTION SYSTEM

Emission Source/Control: RKIQU - Control
Control Type: SPRAY TOWER

Emission Source/Control: 23BT1 - Process

Emission Source/Control: 23BT2 - Process

Emission Source/Control: 23BT3 - Process

Emission Source/Control: 23DHV - Process

Emission Source/Control: 23HT1 - Process

Emission Source/Control: 23HT2 - Process

Emission Source/Control: 23HT3 - Process

Emission Source/Control: 23HT4 - Process

Emission Source/Control: 23HT5 - Process

Emission Source/Control: 23HT6 - Process

Emission Source/Control: 23HT7 - Process

Emission Source/Control: 23TKC - Process

Emission Source/Control: 24ANE - Process

Emission Source/Control: 24SOX - Process

Emission Source/Control: MTCSS - Process

Emission Source/Control: WTVST - Process

Item 477.16(From Mod 1):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 106

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #106 which is a miscellaneous organic manufacturing unit (MCPU) that is



regulated under 40 CFR Part 63 Subpart FFFF. This process operates out of buildings 24 and 37.

Emission Source/Control: 24HLS - Control
Control Type: WET SCRUBBER

Emission Source/Control: 37BDC - Control
Control Type: FABRIC FILTER

Emission Source/Control: 23TK4 - Process

Emission Source/Control: 23TK5 - Process

Emission Source/Control: 23TK7 - Process

Emission Source/Control: 23TKC - Process

Emission Source/Control: 23WBT - Process

Emission Source/Control: 24ANE - Process

Emission Source/Control: 24CHL - Process

Emission Source/Control: 24CHT - Process

Emission Source/Control: 24DRE - Process

Emission Source/Control: 24FTO - Process

Emission Source/Control: 24HT1 - Process

Emission Source/Control: 24HT2 - Process

Emission Source/Control: 24HT4 - Process

Emission Source/Control: 24HTS - Process

Emission Source/Control: 24NO1 - Process

Emission Source/Control: 24PRT - Process

Emission Source/Control: 24SIL - Process

Emission Source/Control: 24T12 - Process

Emission Source/Control: 36ST4 - Process

Emission Source/Control: 374MP - Process

Emission Source/Control: 37APV - Process

Emission Source/Control: 37BDD - Process



- Emission Source/Control: 37CE1 - Process
- Emission Source/Control: 37CE2 - Process
- Emission Source/Control: 37CHT - Process
- Emission Source/Control: 37CRC - Process
- Emission Source/Control: 37CST - Process
- Emission Source/Control: 37D4F - Process
- Emission Source/Control: 37FAT - Process
- Emission Source/Control: 37FEF - Process
- Emission Source/Control: 37FTL - Process
- Emission Source/Control: 37GV1 - Process
- Emission Source/Control: 37MLE - Process
- Emission Source/Control: 37NHT - Process
- Emission Source/Control: 37ST2 - Process
- Emission Source/Control: 37ST3 - Process
- Emission Source/Control: 37ST7 - Process
- Emission Source/Control: 37ST8 - Process
- Emission Source/Control: 37ST9 - Process
- Emission Source/Control: 37STA - Process
- Emission Source/Control: 37STB - Process
- Emission Source/Control: 37STC - Process
- Emission Source/Control: 37TA2 - Process
- Emission Source/Control: 37TA3 - Process
- Emission Source/Control: 37VAC - Process
- Emission Source/Control: 37VCU - Process
- Emission Source/Control: 37VSS - Process

Item 477.17(From Mod 1):

This permit authorizes the following regulated processes for the cited Emission Unit:



Emission Unit: C-27018

Process: 108

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #108 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF.

Emission Source/Control: 71HYS - Control

Control Type: WET SCRUBBER

Emission Source/Control: 76EWS - Control

Control Type: VENTURI SCRUBBER

Emission Source/Control: 71CR1 - Process

Emission Source/Control: 71CR5 - Process

Emission Source/Control: 71CR8 - Process

Emission Source/Control: 71RT1 - Process

Emission Source/Control: 71RT2 - Process

Emission Source/Control: 71WT7 - Process

Emission Source/Control: 76ACW - Process

Emission Source/Control: 76DV1 - Process

Emission Source/Control: 76DV2 - Process

Emission Source/Control: 76DV3 - Process

Emission Source/Control: 76HT6 - Process

Emission Source/Control: 76SKC - Process

Emission Source/Control: 76SPK - Process

Item 477.18(From Mod 1):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 112

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #112 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF. This process operates out of buildings 30, 37, 76 and 78.

Emission Source/Control: 76EWS - Control

Control Type: VENTURI SCRUBBER



Emission Source/Control: 30LET - Process

Emission Source/Control: 30MTA - Process

Emission Source/Control: 30MTB - Process

Emission Source/Control: 30PT1 - Process

Emission Source/Control: 30PT2 - Process

Emission Source/Control: 30SLT - Process

Emission Source/Control: 373MF - Process

Emission Source/Control: 37FAK - Process

Emission Source/Control: 37FPC - Process

Emission Source/Control: 76ACW - Process

Emission Source/Control: 76B15 - Process

Emission Source/Control: 76BIT - Process

Emission Source/Control: 76EFT - Process

Emission Source/Control: 76PST - Process

Emission Source/Control: 76TRE - Process

Emission Source/Control: 78P14 - Process

Emission Source/Control: 78PK1 - Process

Emission Source/Control: 78PK2 - Process

Emission Source/Control: 78VES - Process

Emission Source/Control: PESV1 - Process

Emission Source/Control: PESV2 - Process

Emission Source/Control: PESV3 - Process

Emission Source/Control: PESV5 - Process

Emission Source/Control: PJORS - Process

Emission Source/Control: PKSDT - Process

Emission Source/Control: POLY1 - Process

Emission Source/Control: POLY2 - Process



Emission Source/Control: POLY3 - Process

Emission Source/Control: POLY5 - Process

Item 477.19(From Mod 1):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 113

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #113 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF. This process operates out of buildings 37 and 76.

Emission Source/Control: 76EWS - Control

Control Type: VENTURI SCRUBBER

Emission Source/Control: 76WAS - Control

Control Type: GAS SCRUBBER (GENERAL, NOT CLASSIFIED)

Emission Source/Control: 76WSC - Control

Control Type: FABRIC FILTER

Emission Source/Control: 37ASB - Process

Emission Source/Control: 37EJE - Process

Emission Source/Control: 37EJV - Process

Emission Source/Control: 37MLE - Process

Emission Source/Control: 37RHE - Process

Emission Source/Control: 37RHH - Process

Emission Source/Control: 76ACW - Process

Emission Source/Control: 76CH2 - Process

Emission Source/Control: 76FP2 - Process

Emission Source/Control: 76WFK - Process

Emission Source/Control: 76WHC - Process

Emission Source/Control: 76WHR - Process

Emission Source/Control: 76WHW - Process

Emission Source/Control: 76WHY - Process



Emission Source/Control: 76WPT - Process

Emission Source/Control: 76WSB - Process

Emission Source/Control: 76WSW - Process

Emission Source/Control: RH502 - Process

Emission Source/Control: RHFTK - Process

Emission Source/Control: RHJOD - Process

Emission Source/Control: RHPTK - Process

Emission Source/Control: RHSTD - Process

Emission Source/Control: RHSTE - Process

Emission Source/Control: RHSTL - Process

Item 477.20(From Mod 1):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 119

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #119 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF. This process operates out of buildings 23, 24, 24A and 71.

Emission Source/Control: 23SCR - Control

Control Type: WET SCRUBBER

Emission Source/Control: FBCS1 - Control

Control Type: PACKED-GAS ABSORPTION SYSTEM

Emission Source/Control: FBCS2 - Control

Control Type: PACKED-GAS ABSORPTION SYSTEM

Emission Source/Control: FBIAB - Control

Control Type: DIRECT FLAME AFTERBURNER

Emission Source/Control: FBIQU - Control

Control Type: SPRAY TOWER

Emission Source/Control: IWS11 - Control

Control Type: WET SCRUBBER

Emission Source/Control: IWS12 - Control

Control Type: WET SCRUBBER

Emission Source/Control: IWS1A - Control



Control Type: WET SCRUBBER

Emission Source/Control: IWS1B - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS1C - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS21 - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS22 - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS2A - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS2B - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS2C - Control
Control Type: WET SCRUBBER

Emission Source/Control: RKIAB - Control
Control Type: DIRECT FLAME AFTERBURNER

Emission Source/Control: RKICS - Control
Control Type: PACKED-GAS ABSORPTION SYSTEM

Emission Source/Control: RKIQU - Control
Control Type: SPRAY TOWER

Emission Source/Control: 23BT1 - Process

Emission Source/Control: 23BT2 - Process

Emission Source/Control: 23BT3 - Process

Emission Source/Control: 23DHV - Process

Emission Source/Control: 23HT1 - Process

Emission Source/Control: 23HT2 - Process

Emission Source/Control: 23HT3 - Process

Emission Source/Control: 23HT4 - Process

Emission Source/Control: 23HT5 - Process

Emission Source/Control: 23HT6 - Process

Emission Source/Control: 23HT7 - Process



Emission Source/Control: 23TKU - Process

Emission Source/Control: 24BLK - Process

Emission Source/Control: 24BR2 - Process

Emission Source/Control: 24FK4 - Process

Emission Source/Control: 24HCO - Process

Emission Source/Control: 24SHT - Process

Emission Source/Control: 24WST - Process

Emission Source/Control: MTCSS - Process

Emission Source/Control: WTVST - Process

Item 477.21(From Mod 1):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 123

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #123 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF. This process operates out of buildings 23, 24 and 24A.

Emission Source/Control: 23SCR - Control

Control Type: WET SCRUBBER

Emission Source/Control: 24HLS - Control

Control Type: WET SCRUBBER

Emission Source/Control: 23TK4 - Process

Emission Source/Control: 23TK5 - Process

Emission Source/Control: 23TK7 - Process

Emission Source/Control: 23TKA - Process

Emission Source/Control: 23TKC - Process

Emission Source/Control: 24ANE - Process

Emission Source/Control: 24CHL - Process

Emission Source/Control: 24CHT - Process

Emission Source/Control: 24FTO - Process



Emission Source/Control: 24HT1 - Process

Emission Source/Control: 24HT2 - Process

Emission Source/Control: 24HT4 - Process

Emission Source/Control: 24HTS - Process

Emission Source/Control: 24NO1 - Process

Emission Source/Control: 24PRT - Process

Emission Source/Control: 24SIL - Process

Emission Source/Control: 24SOX - Process

Emission Source/Control: 24T12 - Process

Item 477.22(From Mod 1):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 128

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #128 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF. This process operates out of buildings 24, 71 and 76.

Emission Source/Control: 1MHSC - Control

Control Type: WET SCRUBBER

Emission Source/Control: 23SCR - Control

Control Type: WET SCRUBBER

Emission Source/Control: 71HYS - Control

Control Type: WET SCRUBBER

Emission Source/Control: 76EAS - Control

Control Type: GAS SCRUBBER (GENERAL, NOT CLASSIFIED)

Emission Source/Control: 76ESC - Control

Control Type: FABRIC FILTER

Emission Source/Control: 76EWS - Control

Control Type: VENTURI SCRUBBER

Emission Source/Control: 76WAS - Control

Control Type: GAS SCRUBBER (GENERAL, NOT CLASSIFIED)

Emission Source/Control: 76WSC - Control

Control Type: FABRIC FILTER



Emission Source/Control: FBCS1 - Control
Control Type: PACKED-GAS ABSORPTION SYSTEM

Emission Source/Control: FBCS2 - Control
Control Type: PACKED-GAS ABSORPTION SYSTEM

Emission Source/Control: FBIAB - Control
Control Type: DIRECT FLAME AFTERBURNER

Emission Source/Control: FBIQU - Control
Control Type: SPRAY TOWER

Emission Source/Control: IWS11 - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS12 - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS1A - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS1B - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS1C - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS21 - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS22 - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS2A - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS2B - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS2C - Control
Control Type: WET SCRUBBER

Emission Source/Control: RKIAB - Control
Control Type: DIRECT FLAME AFTERBURNER

Emission Source/Control: RKICS - Control
Control Type: PACKED-GAS ABSORPTION SYSTEM

Emission Source/Control: RKIQU - Control
Control Type: SPRAY TOWER

Emission Source/Control: 23BT1 - Process



Emission Source/Control: 23BT2 - Process

Emission Source/Control: 23BT3 - Process

Emission Source/Control: 23DHV - Process

Emission Source/Control: 23HT1 - Process

Emission Source/Control: 23HT2 - Process

Emission Source/Control: 23HT3 - Process

Emission Source/Control: 23HT4 - Process

Emission Source/Control: 23HT5 - Process

Emission Source/Control: 23HT6 - Process

Emission Source/Control: 23HT7 - Process

Emission Source/Control: 23TKC - Process

Emission Source/Control: 24ANE - Process

Emission Source/Control: 24SOX - Process

Emission Source/Control: 374MP - Process

Emission Source/Control: 374ST - Process

Emission Source/Control: 37750 - Process

Emission Source/Control: 37GW7 - Process

Emission Source/Control: 37PRV - Process

Emission Source/Control: 37PSR - Process

Emission Source/Control: 71CR2 - Process

Emission Source/Control: 71CR7 - Process

Emission Source/Control: 71DS3 - Process

Emission Source/Control: 71FP1 - Process

Emission Source/Control: 71FP3 - Process

Emission Source/Control: 71HES - Process

Emission Source/Control: 71HY3 - Process



Emission Source/Control: 71HZR - Process

Emission Source/Control: 71SIL - Process

Emission Source/Control: 71SWT - Process

Emission Source/Control: 71VAC - Process

Emission Source/Control: 76ACW - Process

Emission Source/Control: 76CH1 - Process

Emission Source/Control: 76CH2 - Process

Emission Source/Control: 76CTL - Process

Emission Source/Control: 76DV1 - Process

Emission Source/Control: 76DV2 - Process

Emission Source/Control: 76DV3 - Process

Emission Source/Control: 76EFK - Process

Emission Source/Control: 76EHC - Process

Emission Source/Control: 76EHW - Process

Emission Source/Control: 76EHY - Process

Emission Source/Control: 76EPT - Process

Emission Source/Control: 76ERC - Process

Emission Source/Control: 76ESB - Process

Emission Source/Control: 76FP1 - Process

Emission Source/Control: 76FP2 - Process

Emission Source/Control: 76HT6 - Process

Emission Source/Control: 76PBT - Process

Emission Source/Control: 76SBS - Process

Emission Source/Control: 76SKC - Process

Emission Source/Control: 76SPK - Process

Emission Source/Control: 76WFK - Process

Emission Source/Control: 76WHC - Process



Emission Source/Control: 76WHR - Process

Emission Source/Control: 76WHW - Process

Emission Source/Control: 76WHY - Process

Emission Source/Control: 76WPT - Process

Emission Source/Control: 76WSB - Process

Emission Source/Control: 76WSW - Process

Item 477.23(From Mod 1):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 135

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #135 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF.

Emission Source/Control: 76EAS - Control

Control Type: GAS SCRUBBER (GENERAL, NOT CLASSIFIED)

Emission Source/Control: 76ESC - Control

Control Type: FABRIC FILTER

Emission Source/Control: 76EWS - Control

Control Type: VENTURI SCRUBBER

Emission Source/Control: 76ACW - Process

Emission Source/Control: 76CH1 - Process

Emission Source/Control: 76DV1 - Process

Emission Source/Control: 76DV2 - Process

Emission Source/Control: 76DV3 - Process

Emission Source/Control: 76EFK - Process

Emission Source/Control: 76EHC - Process

Emission Source/Control: 76EHW - Process

Emission Source/Control: 76EHY - Process

Emission Source/Control: 76EPT - Process

Emission Source/Control: 76ERC - Process



Emission Source/Control: 76ESB - Process

Emission Source/Control: 76FP1 - Process

Emission Source/Control: 76PBT - Process

Emission Source/Control: 76SBS - Process

Emission Source/Control: 76WHW - Process

Emission Source/Control: 76WPT - Process

Item 477.24(From Mod 1):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 150

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #150 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF.

Emission Source/Control: 76EAS - Control

Control Type: GAS SCRUBBER (GENERAL, NOT CLASSIFIED)

Emission Source/Control: 76ESC - Control

Control Type: FABRIC FILTER

Emission Source/Control: 76EWS - Control

Control Type: VENTURI SCRUBBER

Emission Source/Control: 76HTV - Control

Control Type: CONSERVATION VENT

Emission Source/Control: 76WAS - Control

Control Type: GAS SCRUBBER (GENERAL, NOT CLASSIFIED)

Emission Source/Control: 76WSC - Control

Control Type: FABRIC FILTER

Emission Source/Control: 76ACW - Process

Emission Source/Control: 76CH1 - Process

Emission Source/Control: 76CH2 - Process

Emission Source/Control: 76DV1 - Process

Emission Source/Control: 76DV2 - Process

Emission Source/Control: 76DV3 - Process



Emission Source/Control: 76EFK - Process
Emission Source/Control: 76EHC - Process
Emission Source/Control: 76EHW - Process
Emission Source/Control: 76EHY - Process
Emission Source/Control: 76EPT - Process
Emission Source/Control: 76ERC - Process
Emission Source/Control: 76ESB - Process
Emission Source/Control: 76FP1 - Process
Emission Source/Control: 76FP2 - Process
Emission Source/Control: 76HST - Process
Emission Source/Control: 76PBT - Process
Emission Source/Control: 76SBS - Process
Emission Source/Control: 76WFK - Process
Emission Source/Control: 76WHC - Process
Emission Source/Control: 76WHR - Process
Emission Source/Control: 76WHW - Process
Emission Source/Control: 76WHY - Process
Emission Source/Control: 76WPT - Process
Emission Source/Control: 76WSB - Process
Emission Source/Control: 76WSW - Process

Item 477.25(From Mod 1):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 153

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #153 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF.

Emission Source/Control: 23SCR - Control

Control Type: WET SCRUBBER



Emission Source/Control: 24HLS - Control
Control Type: WET SCRUBBER

Emission Source/Control: 23TK4 - Process

Emission Source/Control: 23TK5 - Process

Emission Source/Control: 23TK7 - Process

Emission Source/Control: 23TKA - Process

Emission Source/Control: 23TKC - Process

Emission Source/Control: 24ANE - Process

Emission Source/Control: 24CHL - Process

Emission Source/Control: 24CHT - Process

Emission Source/Control: 24FTO - Process

Emission Source/Control: 24HT1 - Process

Emission Source/Control: 24HT2 - Process

Emission Source/Control: 24HT4 - Process

Emission Source/Control: 24HTS - Process

Emission Source/Control: 24NO1 - Process

Emission Source/Control: 24PRT - Process

Emission Source/Control: 24SIL - Process

Emission Source/Control: 24SOX - Process

Emission Source/Control: 24T12 - Process

Emission Source/Control: 37ART - Process

Emission Source/Control: 37ASB - Process

Emission Source/Control: 37EJE - Process

Emission Source/Control: 37EJV - Process

Emission Source/Control: 37MLE - Process

Emission Source/Control: 37RHE - Process

Emission Source/Control: 37RHH - Process



Emission Source/Control: RH502 - Process

Emission Source/Control: RHJOD - Process

Emission Source/Control: RHPTK - Process

Emission Source/Control: RHSTD - Process

Emission Source/Control: RHSTE - Process

Emission Source/Control: RHSTL - Process

Item 477.26(From Mod 1):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 158

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #158 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF.

Emission Source/Control: 76EWS - Control

Control Type: VENTURI SCRUBBER

Emission Source/Control: 76WAS - Control

Control Type: GAS SCRUBBER (GENERAL, NOT CLASSIFIED)

Emission Source/Control: 76WSC - Control

Control Type: FABRIC FILTER

Emission Source/Control: 76ACW - Process

Emission Source/Control: 76CH2 - Process

Emission Source/Control: 76DV1 - Process

Emission Source/Control: 76DV2 - Process

Emission Source/Control: 76DV3 - Process

Emission Source/Control: 76FP2 - Process

Emission Source/Control: 76HT6 - Process

Emission Source/Control: 76SKC - Process

Emission Source/Control: 76SPK - Process

Emission Source/Control: 76TRD - Process

Emission Source/Control: 76WFK - Process



Emission Source/Control: 76WHC - Process

Emission Source/Control: 76WHR - Process

Emission Source/Control: 76WHW - Process

Emission Source/Control: 76WHY - Process

Emission Source/Control: 76WPT - Process

Emission Source/Control: 76WSB - Process

Emission Source/Control: 76WSW - Process

Item 477.27(From Mod 1):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 167

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #167 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Oart 63 Subpart FFFF.

Emission Source/Control: 24CHI - Process

Emission Source/Control: 24CHL - Process

Emission Source/Control: 24CHT - Process

Item 477.28(From Mod 1):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 168

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #168 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF. This process operates out of buildings 23, 24 and 24A.

Emission Source/Control: 23SCR - Control

Control Type: WET SCRUBBER

Emission Source/Control: 24PGA - Control

Control Type: PACKED-GAS ABSORPTION SYSTEM

Emission Source/Control: FBCS1 - Control

Control Type: PACKED-GAS ABSORPTION SYSTEM

Emission Source/Control: FBCS2 - Control

Control Type: PACKED-GAS ABSORPTION SYSTEM



Emission Source/Control: FBIAB - Control
Control Type: DIRECT FLAME AFTERBURNER

Emission Source/Control: FBIQU - Control
Control Type: SPRAY TOWER

Emission Source/Control: IWS11 - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS12 - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS1A - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS1B - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS1C - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS21 - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS22 - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS2A - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS2B - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS2C - Control
Control Type: WET SCRUBBER

Emission Source/Control: RKIAB - Control
Control Type: DIRECT FLAME AFTERBURNER

Emission Source/Control: RKICS - Control
Control Type: PACKED-GAS ABSORPTION SYSTEM

Emission Source/Control: RKIQU - Control
Control Type: SPRAY TOWER

Emission Source/Control: 23TKC - Process

Emission Source/Control: 24AID - Process

Emission Source/Control: 24ANE - Process

Emission Source/Control: 24ART - Process



Emission Source/Control: 24BD1 - Process

Emission Source/Control: 24BD2 - Process

Emission Source/Control: 24BLK - Process

Emission Source/Control: 24BR2 - Process

Emission Source/Control: 24FK4 - Process

Emission Source/Control: 24FOK - Process

Emission Source/Control: 24HCO - Process

Emission Source/Control: 24N12 - Process

Emission Source/Control: 24NO5 - Process

Emission Source/Control: 24PCT - Process

Emission Source/Control: 24SF1 - Process

Emission Source/Control: 24SF2 - Process

Emission Source/Control: 24SHT - Process

Emission Source/Control: 24SOU - Process

Emission Source/Control: 24SOX - Process

Emission Source/Control: 24SRA - Process

Emission Source/Control: 24WST - Process

Emission Source/Control: 24WTA - Process

Item 477.29(From Mod 1):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 213

Source Classification Code: 3-01-820-10

Process Description:

This process represents the management of Group 1 process wastewater that is generated by miscellaneous chemical manufacturing units (MCPUs) that are regulated under 40 CFR Part 63, Subpart FFFF (Miscellaneous Organic Chemical Manufacturing).

Emission Source/Control: DSSTR - Control

Control Type: GAS SCRUBBER (GENERAL, NOT CLASSIFIED)

Emission Source/Control: EQIFR - Control

Control Type: FLOATING ROOF



Emission Source/Control: FBCS1 - Control
Control Type: PACKED-GAS ABSORPTION SYSTEM

Emission Source/Control: FBCS2 - Control
Control Type: PACKED-GAS ABSORPTION SYSTEM

Emission Source/Control: FBIAB - Control
Control Type: DIRECT FLAME AFTERBURNER

Emission Source/Control: FBIQU - Control
Control Type: SPRAY TOWER

Emission Source/Control: IWS11 - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS12 - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS1A - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS1B - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS1C - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS21 - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS22 - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS2A - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS2B - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS2C - Control
Control Type: WET SCRUBBER

Emission Source/Control: RKIAB - Control
Control Type: DIRECT FLAME AFTERBURNER

Emission Source/Control: RKICS - Control
Control Type: PACKED-GAS ABSORPTION SYSTEM

Emission Source/Control: RKIQU - Control
Control Type: SPRAY TOWER

Emission Source/Control: 150EQ - Process



Emission Source/Control: 20KEQ - Process Removal Date: 05/10/2007

Emission Source/Control: 40KEQ - Process
Design Capacity: 40,000 gallons

Emission Source/Control: WTVST - Process

Item 477.30(From Mod 1):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 400

Source Classification Code: 6-84-800-01

Process Description:

Equipment leaks. This process represents closed vent system, compressor, connector, pressure relief valve, pump, sampling connection, vessel and receiver, and valve leaks for the Methyl Chloride chemical manufacturing process unit.

Emission Source/Control: FUGTV - Process

Item 477.31(From Mod 1):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 401

Source Classification Code: 3-99-999-94

Process Description:

MCS to incinerators/scrubbers. This process consists of sources in the Methyl Chlorosilane operations area which vent to the waste incinerators, the MCS vent incinerator, or the MCS vent scrubber.

Emission Source/Control: 62EST - Control
Control Type: SPRAY TOWER

Emission Source/Control: 62EVS - Control
Control Type: VENTURI SCRUBBER

Emission Source/Control: 62WST - Control
Control Type: SPRAY TOWER

Emission Source/Control: 62WVS - Control
Control Type: VENTURI SCRUBBER

Emission Source/Control: FBCS1 - Control
Control Type: PACKED-GAS ABSORPTION SYSTEM

Emission Source/Control: FBCS2 - Control
Control Type: PACKED-GAS ABSORPTION SYSTEM

Emission Source/Control: FBIAB - Control
Control Type: DIRECT FLAME AFTERBURNER



Emission Source/Control: IWS11 - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS12 - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS1A - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS1B - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS21 - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS22 - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS2A - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS2B - Control
Control Type: WET SCRUBBER

Emission Source/Control: MCSVI - Control
Control Type: DIRECT FLAME AFTERBURNER

Emission Source/Control: MCSVS - Control
Control Type: WET SCRUBBER

Emission Source/Control: RKIAB - Control
Control Type: DIRECT FLAME AFTERBURNER

Emission Source/Control: RKICS - Control
Control Type: PACKED-GAS ABSORPTION SYSTEM

Emission Source/Control: 62FH1 - Process

Emission Source/Control: 62FH2 - Process

Emission Source/Control: 62H2O - Process

Emission Source/Control: 62MCT - Process

Emission Source/Control: 62RCL - Process

Emission Source/Control: 62RP2 - Process

Emission Source/Control: 62SC2 - Process

Emission Source/Control: 62SC3 - Process



Emission Source/Control: 62SC4 - Process

Emission Source/Control: 62SP4 - Process

Emission Source/Control: 62T56 - Process

Emission Source/Control: 62TAB - Process

Item 477.32(From Mod 1):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 405

Source Classification Code: 3-01-070-02

Process Description:

Water scrubber, spent sulfuric storage tank and loading.
Sulfuric acid fumes are vented from the head space of the
spent sulfuric acid tank.

Emission Source/Control: 27PGA - Control

Control Type: PACKED-GAS ABSORPTION SYSTEM

Emission Source/Control: 27SST - Process

Item 477.33(From Mod 1):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 406

Source Classification Code: 3-85-001-10

Process Description:

Heat exchange system. This process represents cooling
water from heat exchange systems within the Methyl
Chloride chemical manufacturing process unit.

Emission Source/Control: HXCWW - Process

Item 477.34(From Mod 1):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 422

Source Classification Code: 5-03-007-01

Process Description: RKI Normal Operation

Emission Source/Control: IWS1A - Control

Control Type: WET SCRUBBER

Emission Source/Control: IWS1B - Control

Control Type: WET SCRUBBER

Emission Source/Control: IWS1C - Control

Control Type: WET SCRUBBER

Emission Source/Control: IWS2A - Control

Control Type: WET SCRUBBER



Emission Source/Control: IWS2B - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS2C - Control
Control Type: WET SCRUBBER

Emission Source/Control: RKICS - Control
Control Type: PACKED-GAS ABSORPTION SYSTEM

Emission Source/Control: RKIQU - Control
Control Type: SPRAY TOWER

Emission Source/Control: 96RKI - Incinerator
Design Capacity: 30 million Btu per hour
Waste Feed Method: MANUAL DIRECT FEED
Waste Type: HAZARDOUS WASTE

Emission Source/Control: WTPAS - Process

Item 477.35(From Mod 1):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018
Process: 423 Source Classification Code: 5-03-007-01
Process Description: RKI Maintenance Operation.

Emission Source/Control: IWS1A - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS1B - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS1C - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS2A - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS2B - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS2C - Control
Control Type: WET SCRUBBER

Emission Source/Control: RKICS - Control
Control Type: PACKED-GAS ABSORPTION SYSTEM

Emission Source/Control: RKIQU - Control
Control Type: SPRAY TOWER

Emission Source/Control: 96RKI - Incinerator
Design Capacity: 30 million Btu per hour



Waste Feed Method: MANUAL DIRECT FEED
Waste Type: HAZARDOUS WASTE

Emission Source/Control: WTPAS - Process

Item 477.36(From Mod 1):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018
Process: 424 Source Classification Code: 5-03-007-01
Process Description: Fixed Box Normal Operation.

Emission Source/Control: FBCS1 - Control
Control Type: PACKED-GAS ABSORPTION SYSTEM

Emission Source/Control: FBCS2 - Control
Control Type: PACKED-GAS ABSORPTION SYSTEM

Emission Source/Control: FBIQU - Control
Control Type: SPRAY TOWER

Emission Source/Control: IWS11 - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS12 - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS21 - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS22 - Control
Control Type: WET SCRUBBER

Emission Source/Control: 936FB - Incinerator
Design Capacity: 27.1 million Btu per hour
Waste Feed Method: MANUAL DIRECT FEED
Waste Type: HAZARDOUS WASTE

Emission Source/Control: WTPAS - Process

Item 477.37(From Mod 1):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018
Process: 425 Source Classification Code: 3-01-999-99
Process Description: Fixed Box Maintenance Operation.

Emission Source/Control: FBCS1 - Control
Control Type: PACKED-GAS ABSORPTION SYSTEM

Emission Source/Control: FBCS2 - Control
Control Type: PACKED-GAS ABSORPTION SYSTEM



Emission Source/Control: FBIQU - Control
Control Type: SPRAY TOWER

Emission Source/Control: IWS11 - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS12 - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS21 - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS22 - Control
Control Type: WET SCRUBBER

Emission Source/Control: 936FB - Incinerator
Design Capacity: 27.1 million Btu per hour
Waste Feed Method: MANUAL DIRECT FEED
Waste Type: HAZARDOUS WASTE

Emission Source/Control: WTPAS - Process

Item 477.38(From Mod 1):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 703

Source Classification Code: 3-99-999-94

Process Description:

MCS IV Methyl Chloride recovery column. This process consists of the MCS IV Methyl Chloride recovery column which vents to the MCS vent incinerator or the waste incinerator.

Emission Source/Control: FBCS1 - Control
Control Type: PACKED-GAS ABSORPTION SYSTEM

Emission Source/Control: FBCS2 - Control
Control Type: PACKED-GAS ABSORPTION SYSTEM

Emission Source/Control: FBIAB - Control
Control Type: DIRECT FLAME AFTERBURNER

Emission Source/Control: FBIQU - Control
Control Type: SPRAY TOWER

Emission Source/Control: IWS11 - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS12 - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS1A - Control
Control Type: WET SCRUBBER



Emission Source/Control: IWS1B - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS1C - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS21 - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS22 - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS2A - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS2B - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS2C - Control
Control Type: WET SCRUBBER

Emission Source/Control: M4CCS - Control
Control Type: VAPOR RECOVERY SYS(INCL.
CONDENSERS,HOODING, OTHER ENCLOSURES)

Emission Source/Control: M4VCS - Control
Control Type: VAPOR RECOVERY SYS(INCL.
CONDENSERS,HOODING, OTHER ENCLOSURES)

Emission Source/Control: MCSVI - Control
Control Type: DIRECT FLAME AFTERBURNER

Emission Source/Control: MCSVS - Control
Control Type: WET SCRUBBER

Emission Source/Control: RKIAB - Control
Control Type: DIRECT FLAME AFTERBURNER

Emission Source/Control: RKICS - Control
Control Type: PACKED-GAS ABSORPTION SYSTEM

Emission Source/Control: RKIQU - Control
Control Type: SPRAY TOWER

Emission Source/Control: M4MRC - Process

Item 477.39(From Mod 1):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 707

Source Classification Code: 3-01-840-01

Process Description:



Emission Source/Control: 24PGA - Control
Control Type: PACKED-GAS ABSORPTION SYSTEM

Emission Source/Control: 24EST - Process

Emission Source/Control: 24SOU - Process

Item 477.42(From Mod 1):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 724

Source Classification Code: 3-99-999-94

Process Description:

Batch Mixing The 3000 liter north and the 3000 liter south Drais mixers vent to venturi scrubbers during filler charges.

Emission Source/Control: 31FS1 - Control
Control Type: WET SCRUBBER

Emission Source/Control: 31FS2 - Process

Emission Source/Control: 31LNM - Process

Emission Source/Control: 31LSM - Process

Item 477.43(From Mod 1):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27035

Process: 056

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #056 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF.

Emission Source/Control: 27HWT - Control
Control Type: SPRAY TOWER

Emission Source/Control: 27526 - Process

Emission Source/Control: ABWAT - Process

Emission Source/Control: HCLT1 - Process

Emission Source/Control: HCLT2 - Process

Emission Source/Control: HCLT3 - Process

Emission Source/Control: HCLT4 - Process

Emission Source/Control: HCLT5 - Process



Item 477.44(From Mod 1):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: E-GNRTR

Process: 421

Source Classification Code: 2-01-001-02

Process Description:

This process includes the operation of emergency generators.

Emission Source/Control: 28EG1 - Combustion

Design Capacity: 120 horsepower hours

Emission Source/Control: 28EG2 - Combustion

Design Capacity: 425 horsepower hours

Emission Source/Control: 28EG3 - Combustion

Design Capacity: 408 horsepower hours

Emission Source/Control: 51EG3 - Combustion

Design Capacity: 258 horsepower hours

Emission Source/Control: 51EG4 - Combustion

Design Capacity: 258 horsepower hours

Emission Source/Control: 80EG1 - Combustion

Design Capacity: 120 horsepower hours

Emission Source/Control: 80EG2 - Combustion

Design Capacity: 40 horsepower hours

Emission Source/Control: 85EG1 - Combustion

Design Capacity: 82 horsepower hours

Emission Source/Control: 86EG1 - Combustion

Design Capacity: 700 horsepower hours

Emission Source/Control: 86EG2 - Combustion

Design Capacity: 638 horsepower hours

Emission Source/Control: 93EG1 - Combustion

Design Capacity: 176 horsepower hours

Emission Source/Control: 952E1 - Combustion

Design Capacity: 500 horsepower hours

Emission Source/Control: 952E2 - Combustion

Design Capacity: 500 horsepower hours

Emission Source/Control: 96EG1 - Combustion

Design Capacity: 738 horsepower hours

Emission Source/Control: 96EG2 - Combustion



Design Capacity: 420 horsepower hours

Item 477.45(From Mod 1):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: F-INISH

Process: 053

Source Classification Code: 3-01-999-99

Process Description:

This process represents FOM 053, which is a miscellaneous organic chemical manufacturing unit (MCPU) that is regulated under 40 CFR Part 63, Subpart FFFF (Miscellaneous Organic Chemical Manufacturing)

Emission Source/Control: 76CSS - Control

Control Type: GAS SCRUBBER (GENERAL, NOT CLASSIFIED)

Emission Source/Control: 76AAS - Process

Design Capacity: 16,000 gallons

Emission Source/Control: 76BTC - Process

Emission Source/Control: 76HLD - Process

Emission Source/Control: 76PTA - Process

Emission Source/Control: 76PW1 - Process

Emission Source/Control: 76PW2 - Process

Emission Source/Control: 76RCT - Process

Emission Source/Control: 76RET - Process

Emission Source/Control: 76TRA - Process

Emission Source/Control: 76TRC - Process

Item 477.46(From Mod 1):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: F-INISH

Process: 069

Source Classification Code: 3-01-999-99

Process Description:

This process represents FOM 069, which is a miscellaneous organic chemical manufacturing unit (MCPU) that is regulated under 40 CFR Part 63, Subpart FFFF (Miscellaneous Organic Chemical Manufacturing)

Emission Source/Control: 76CSS - Control

Control Type: GAS SCRUBBER (GENERAL, NOT CLASSIFIED)

Emission Source/Control: 76BTC - Process



Emission Source/Control: 76HLD - Process

Emission Source/Control: 76PTA - Process

Emission Source/Control: 76PW1 - Process

Emission Source/Control: 76PW2 - Process

Emission Source/Control: 76RCT - Process

Emission Source/Control: 76RET - Process

Item 477.47(From Mod 1):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: F-INISH

Process: 092

Source Classification Code: 3-01-999-99

Process Description:

This process represents FOM 092, which is a miscellaneous organic chemical manufacturing unit (MCPU) that is regulated under 40 CFR Part 63, Subpart FFFF (Miscellaneous Organic Chemical Manufacturing)

Emission Source/Control: 71VCS - Control

Control Type: VAPOR RECOVERY SYSTEMS, REFRIGERATED CONDENSER, GAS SCRUBBER (GENERAL)

Emission Source/Control: 71FR1 - Process

Emission Source/Control: 71FR2 - Process

Emission Source/Control: 71FSR - Process

Emission Source/Control: 71FWT - Process

Item 477.48(From Mod 1):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: F-INISH

Process: 157

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #157 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR 63 Subpart FFFF.

Emission Source/Control: 32PGA - Control

Control Type: PACKED-GAS ABSORPTION SYSTEM

Emission Source/Control: 32TV1 - Control

Control Type: VAPOR RECOVERY SYS(INCL. CONDENSERS,HOODING, OTHER ENCLOSURES)

Emission Source/Control: 32TV2 - Control



Control Type: VAPOR RECOVERY SYS(INCL.
CONDENSERS,HOODING, OTHER ENCLOSURES)

Emission Source/Control: 32TWH - Control
Control Type: FABRIC FILTER

Emission Source/Control: 32WH1 - Process

Emission Source/Control: 32WH2 - Process

Emission Source/Control: 32WH3 - Process

Emission Source/Control: 32WH4 - Process

Emission Source/Control: 32WH5 - Process

Emission Source/Control: 85DUH - Process

Emission Source/Control: 85LEC - Process

Emission Source/Control: 85TF4 - Process

Emission Source/Control: 85TF5 - Process

Emission Source/Control: 85TK5 - Process

Emission Source/Control: 85TWT - Process

Emission Source/Control: FTKR1 - Process

Emission Source/Control: FTKR2 - Process

Emission Source/Control: FTKR4 - Process

Emission Source/Control: FTKR5 - Process

Emission Source/Control: FTKT2 - Process

Emission Source/Control: FTKT3 - Process

Emission Source/Control: TFK02 - Process

Emission Source/Control: TFK03 - Process

Emission Source/Control: TFKH2 - Process

Item 477.49(From Mod 1):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: F-INISH

Process: 169

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #169 which is a



miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Oart 63 Subpart FFFF.

Emission Source/Control: 76CSS - Control
Control Type: GAS SCRUBBER (GENERAL, NOT CLASSIFIED)

Emission Source/Control: 76BTC - Process

Emission Source/Control: 76COO - Process

Emission Source/Control: 76HLD - Process

Emission Source/Control: 76PTA - Process

Emission Source/Control: 76PW1 - Process

Emission Source/Control: 76PW2 - Process

Emission Source/Control: 76RCT - Process

Emission Source/Control: 76RET - Process

Item 477.50(From Mod 1):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: F-INISH

Process: 712

Source Classification Code: 3-01-026-30

Process Description:

South resins. During the vacuum process, emissions from a body kettle condenser pass through a receiver to a vacuum eductor and out to the atmosphere.

Emission Source/Control: 24BC1 - Process

Emission Source/Control: 24SRC - Process

Item 477.51(From Mod 1):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: F-INISH

Process: 713

Source Classification Code: 3-01-026-30

Process Description:

East resins. During the vacuum process, emissions from a body kettle condenser pass through a receiver to a vacuum eductor and out to the atmosphere.

Emission Source/Control: 24EVR - Control

Control Type: VAPOR RECOVERY SYS(INCL.

CONDENSERS,HOODING, OTHER ENCLOSURES)

Emission Source/Control: 24BC2 - Process

Emission Source/Control: 24SRC - Process



Item 477.52(From Mod 1):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: F-INISH

Process: 714

Source Classification Code: 3-01-026-30

Process Description:

Doughmixer area - doughmixers #5,6,7,8, and 9 vent to a condenser and a receiver vent. The doughmixers are batch mixers used in the production of various products.

Emission Source/Control: DMXR5 - Process

Emission Source/Control: DMXR6 - Process

Emission Source/Control: DMXR7 - Process

Emission Source/Control: DMXR8 - Process

Emission Source/Control: DMXR9 - Process

Item 477.53(From Mod 1):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: F-INISH

Process: 717

Source Classification Code: 3-01-026-30

Process Description:

Treater filler kettle - treater filler kettle is used to treat raw filler with HMDZ. HMDZ vapors are discharged to receiver and ultimately to a packed tower scrubber. Tank wagon emissions also vented to scrubber.

Emission Source/Control: FTKT3 - Process

Emission Source/Control: TFK03 - Process

Item 477.54(From Mod 1):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: F-INISH

Process: 718

Source Classification Code: 3-99-999-94

Process Description:

1500 Phenyl reactor (Diol and Tetramer). A batch system used to manufacture phenyl diol and Phenyl Tetramer.

Emission Source/Control: 37PTC - Process

Emission Source/Control: 37PTD - Process

Emission Source/Control: 37PTE - Process

Emission Source/Control: 37PTH - Process



Item 477.55(From Mod 1):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: F-INISH

Process: 720

Source Classification Code: 3-01-070-02

Process Description:

Treater Filler Kettles The Methyl Tetramer (D4) recovery system consists of a vapor condensing tower, a D4 circulating tank, a knock out pot, and a light-ends weigh tank. D4 vapor and Nitrogen are released from treated filler kettles and transferred to the recovery system.

Emission Source/Control: 85LEC - Process

Item 477.56(From Mod 1):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: F-INISH

Process: 721

Source Classification Code: 3-01-026-30

Process Description:

Treater Filler Kettles Treater filler kettles are used to treat raw fillers with Methyl Tetramer. Methyl Tetramer vapors are discharged to a condenser/receiver system.

Emission Source/Control: FTKT2 - Process

Emission Source/Control: FTKT3 - Process

Emission Source/Control: TFK02 - Process

Emission Source/Control: TFK03 - Process

Item 477.57(From Mod 1):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: F-INISH

Process: 728

Source Classification Code: 3-01-026-30

Process Description:

1M Fluorosilicone reactor. A 1000 gallon batch system used to manufacture Fluorosilicone Polysiloxane. The process consists of two steps: production of 88536 followed by hydrolysis. Major equipment includes a reactor, weigh tank, and two receivers.

Emission Source/Control: 71FSR - Process

Item 477.58(From Mod 1):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: H-OFURN

Process: 418

Source Classification Code: 1-02-006-02

Process Description:



This process includes the operation of hot oil furnaces.

Emission Source/Control: 21HOF - Combustion

Emission Source/Control: 35HOF - Combustion

Emission Source/Control: 62HOF - Combustion

Emission Source/Control: 85HOF - Combustion

Item 477.59(From Mod 1):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: H-OFURN

Process: 426

Source Classification Code: 1-02-005-01

Process Description:

This process includes the operation of hot oil furnaces to replace the existing 21HOF and 35HOF upon reconfiguration of the existing 12.5 mmBTU/hr natural gas burners with 15 mmBTU/hr natural gas burners. These furnaces are in building 21 and 35.

Emission Source/Control: 21HOF - Combustion

Emission Source/Control: 35HOF - Combustion

Item 477.60(From Mod 1):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: U-28002

Process: 410

Source Classification Code: 1-02-006-01

Process Description: Boiler 18 - natural gas combustion.

Emission Source/Control: BLR18 - Combustion

Emission Source/Control: 18LNB - Control

Control Type: DRY LOW NO_x BURNER

Item 477.61(From Mod 1):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: U-28002

Process: 411

Source Classification Code: 1-02-005-01

Process Description: #2 fuel oil combustion for boiler #18

Emission Source/Control: BLR18 - Combustion

Emission Source/Control: 18LNB - Control

Control Type: DRY LOW NO_x BURNER

Item 477.62(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:



Emission Unit: C-27018

Process: 001

Source Classification Code: 3-01-999-99

Process Description:

This process represents FOM 001, which is a miscellaneous organic chemical manufacturing unit (MCPU) that is regulated under 40 CFR Part 63, Subpart FFFF (Miscellaneous Organic Chemical Manufacturing).

Emission Source/Control: 71HYS - Control

Control Type: WET SCRUBBER

Emission Source/Control: 71CR1 - Process

Emission Source/Control: 71CR5 - Process

Emission Source/Control: 71CR8 - Process

Emission Source/Control: 71RT1 - Process

Emission Source/Control: 71RT2 - Process

Emission Source/Control: 71WT7 - Process

Item 477.63(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 002

Source Classification Code: 3-01-999-99

Process Description:

This process represents FOM 002, which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63, Subpart FFFF (Miscellaneous Organic Chemical Manufacturing).

Emission Source/Control: 71HYS - Control

Control Type: WET SCRUBBER

Emission Source/Control: 71CR1 - Process

Emission Source/Control: 71CR2 - Process

Emission Source/Control: 71CR5 - Process

Emission Source/Control: 71CR7 - Process

Emission Source/Control: 71CR8 - Process

Emission Source/Control: 71DS3 - Process

Emission Source/Control: 71FP3 - Process

Emission Source/Control: 71HY3 - Process



Emission Source/Control: 71RT1 - Process

Emission Source/Control: 71RT2 - Process

Emission Source/Control: 71SIL - Process

Emission Source/Control: 71SWT - Process

Emission Source/Control: 71WT7 - Process

Item 477.64(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 003

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #003, which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63, Subpart FFFF.

Emission Source/Control: 71HYS - Control
Control Type: WET SCRUBBER

Emission Source/Control: 71CR1 - Process

Emission Source/Control: 71CR5 - Process

Emission Source/Control: 71CR8 - Process

Emission Source/Control: 71RT1 - Process

Emission Source/Control: 71RT2 - Process

Emission Source/Control: 71WT7 - Process

Item 477.65(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 005

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #005, which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63, Subpart FFFF.

Emission Source/Control: 78HWV - Process

Emission Source/Control: 78MVS - Process

Emission Source/Control: 78PKV - Process

Emission Source/Control: 78RVC - Process



Item 477.66(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 006

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #006, which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63, Subpart FFFF.

Emission Source/Control: 78PK2 - Process

Emission Source/Control: 78VES - Process

Item 477.67(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 007

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #007, which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63, Subpart FFFF.

Emission Source/Control: 14RMX - Process

Item 477.68(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 008

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #007, which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63, Subpart FFFF.

Emission Source/Control: 37BDC - Control
Control Type: FABRIC FILTER

Emission Source/Control: 36ST4 - Process

Emission Source/Control: 374MP - Process

Emission Source/Control: 37APV - Process

Emission Source/Control: 37BDD - Process

Emission Source/Control: 37CE1 - Process

Emission Source/Control: 37CE2 - Process

Emission Source/Control: 37CHT - Process



- Emission Source/Control: 37CRE - Process
- Emission Source/Control: 37CST - Process
- Emission Source/Control: 37D4F - Process
- Emission Source/Control: 37FAT - Process
- Emission Source/Control: 37FEF - Process
- Emission Source/Control: 37FTL - Process
- Emission Source/Control: 37GV1 - Process
- Emission Source/Control: 37MLE - Process
- Emission Source/Control: 37NHT - Process
- Emission Source/Control: 37ST2 - Process
- Emission Source/Control: 37ST3 - Process
- Emission Source/Control: 37ST7 - Process
- Emission Source/Control: 37ST8 - Process
- Emission Source/Control: 37ST9 - Process
- Emission Source/Control: 37STA - Process
- Emission Source/Control: 37STB - Process
- Emission Source/Control: 37STC - Process
- Emission Source/Control: 37TA2 - Process
- Emission Source/Control: 37TA3 - Process
- Emission Source/Control: 37VAC - Process
- Emission Source/Control: 37VCU - Process
- Emission Source/Control: 37VSS - Process

Item 477.69(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 009

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #009, which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63, Subpart FFFF.



Emission Source/Control: 37BDC - Control
Control Type: FABRIC FILTER

Emission Source/Control: 36ST4 - Process

Emission Source/Control: 374MP - Process

Emission Source/Control: 37APV - Process

Emission Source/Control: 37BDD - Process

Emission Source/Control: 37CE1 - Process

Emission Source/Control: 37CE2 - Process

Emission Source/Control: 37CHT - Process

Emission Source/Control: 37CRE - Process

Emission Source/Control: 37CST - Process

Emission Source/Control: 37D4F - Process

Emission Source/Control: 37FAT - Process

Emission Source/Control: 37FEF - Process

Emission Source/Control: 37FTL - Process

Emission Source/Control: 37GV1 - Process

Emission Source/Control: 37MLE - Process

Emission Source/Control: 37NHT - Process

Emission Source/Control: 37ST2 - Process

Emission Source/Control: 37ST3 - Process

Emission Source/Control: 37ST7 - Process

Emission Source/Control: 37ST8 - Process

Emission Source/Control: 37ST9 - Process

Emission Source/Control: 37STA - Process

Emission Source/Control: 37STB - Process

Emission Source/Control: 37STC - Process

Emission Source/Control: 37TA2 - Process



Emission Source/Control: 37TA3 - Process

Emission Source/Control: 37VAC - Process

Emission Source/Control: 37VCU - Process

Emission Source/Control: 37VSS - Process

Item 477.70(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 010

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #010, which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63, Subpart FFFF.

Emission Source/Control: 37BDC - Control

Control Type: FABRIC FILTER

Emission Source/Control: 36ST4 - Process

Emission Source/Control: 374MP - Process

Emission Source/Control: 37APV - Process

Emission Source/Control: 37BDD - Process

Emission Source/Control: 37CE1 - Process

Emission Source/Control: 37CE2 - Process

Emission Source/Control: 37CHT - Process

Emission Source/Control: 37CRE - Process

Emission Source/Control: 37CST - Process

Emission Source/Control: 37D4F - Process

Emission Source/Control: 37FAT - Process

Emission Source/Control: 37FEF - Process

Emission Source/Control: 37FTL - Process

Emission Source/Control: 37GV1 - Process

Emission Source/Control: 37MLE - Process

Emission Source/Control: 37NHT - Process



Emission Source/Control: 37ST2 - Process

Emission Source/Control: 37ST3 - Process

Emission Source/Control: 37ST7 - Process

Emission Source/Control: 37ST8 - Process

Emission Source/Control: 37ST9 - Process

Emission Source/Control: 37STA - Process

Emission Source/Control: 37STB - Process

Emission Source/Control: 37STC - Process

Emission Source/Control: 37TA2 - Process

Emission Source/Control: 37TA3 - Process

Emission Source/Control: 37VAC - Process

Emission Source/Control: 37VCU - Process

Emission Source/Control: 37VSS - Process

Item 477.71(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 011

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #011, which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63, Subpart FFFF.

Emission Source/Control: 37BDC - Control

Control Type: FABRIC FILTER

Emission Source/Control: 36ST4 - Process

Emission Source/Control: 374MP - Process

Emission Source/Control: 37APV - Process

Emission Source/Control: 37BDD - Process

Emission Source/Control: 37CE1 - Process

Emission Source/Control: 37CE2 - Process

Emission Source/Control: 37CHT - Process



Emission Source/Control: 37CRE - Process
Emission Source/Control: 37CST - Process
Emission Source/Control: 37D4F - Process
Emission Source/Control: 37FAT - Process
Emission Source/Control: 37FEF - Process
Emission Source/Control: 37FTL - Process
Emission Source/Control: 37GV1 - Process
Emission Source/Control: 37MLE - Process
Emission Source/Control: 37NHT - Process
Emission Source/Control: 37ST2 - Process
Emission Source/Control: 37ST3 - Process
Emission Source/Control: 37ST7 - Process
Emission Source/Control: 37ST8 - Process
Emission Source/Control: 37ST9 - Process
Emission Source/Control: 37STA - Process
Emission Source/Control: 37STB - Process
Emission Source/Control: 37STC - Process
Emission Source/Control: 37TA2 - Process
Emission Source/Control: 37TA3 - Process
Emission Source/Control: 37VAC - Process
Emission Source/Control: 37VCU - Process
Emission Source/Control: 37VSS - Process

Item 477.72(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 012

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #012, which is a miscellaneous organic manufacturing unit (MCPU) that is



regulated under 40 CFR Part 63, Subpart FFFF.

Emission Source/Control: 78PK2 - Process

Emission Source/Control: 78VES - Process

Item 477.73(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 023

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #023, which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63, Subpart FFFF.

Emission Source/Control: 30LET - Process

Emission Source/Control: 30MTA - Process

Emission Source/Control: 30MTB - Process

Emission Source/Control: 30PT1 - Process

Emission Source/Control: 30PT2 - Process

Emission Source/Control: 30SLT - Process

Emission Source/Control: PESV1 - Process

Emission Source/Control: PESV2 - Process

Emission Source/Control: PESV3 - Process

Emission Source/Control: PESV5 - Process

Emission Source/Control: PJORS - Process

Emission Source/Control: PKSDT - Process

Emission Source/Control: POLY1 - Process

Emission Source/Control: POLY2 - Process

Emission Source/Control: POLY3 - Process

Emission Source/Control: POLY5 - Process

Item 477.74(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 024

Source Classification Code: 3-01-999-99



Process Description:

Equipment for Family of Material #024, which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63, Subpart FFFF.

Emission Source/Control: 30LET - Process

Emission Source/Control: 30MTA - Process

Emission Source/Control: 30MTB - Process

Emission Source/Control: 30PT1 - Process

Emission Source/Control: 30PT2 - Process

Emission Source/Control: 30SLT - Process

Emission Source/Control: PESV1 - Process

Emission Source/Control: PESV2 - Process

Emission Source/Control: PESV3 - Process

Emission Source/Control: PESV5 - Process

Emission Source/Control: PJORS - Process

Emission Source/Control: PKSDT - Process

Emission Source/Control: POLY1 - Process

Emission Source/Control: POLY2 - Process

Emission Source/Control: POLY3 - Process

Emission Source/Control: POLY5 - Process

Item 477.75(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 025

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #025, which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63, Subpart FFFF. This process operates out of building 30 and 78.

Emission Source/Control: 30LET - Process

Emission Source/Control: 30MTA - Process

Emission Source/Control: 30MTB - Process



Emission Source/Control: 30PT1 - Process
Emission Source/Control: 30PT2 - Process
Emission Source/Control: 30SLT - Process
Emission Source/Control: 78HWV - Process
Emission Source/Control: 78MVS - Process
Emission Source/Control: 78PKV - Process
Emission Source/Control: PESV1 - Process
Emission Source/Control: PESV2 - Process
Emission Source/Control: PESV3 - Process
Emission Source/Control: PESV5 - Process
Emission Source/Control: PJORS - Process
Emission Source/Control: PKSDT - Process
Emission Source/Control: POLY1 - Process
Emission Source/Control: POLY2 - Process
Emission Source/Control: POLY3 - Process
Emission Source/Control: POLY5 - Process

Item 477.76(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 026

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #026, which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63, Subpart FFFF.

Emission Source/Control: 30LET - Process
Emission Source/Control: 30MTA - Process
Emission Source/Control: 30MTB - Process
Emission Source/Control: 30PT1 - Process
Emission Source/Control: 30PT2 - Process



Emission Source/Control: 30SLT - Process

Emission Source/Control: PESV1 - Process

Emission Source/Control: PESV2 - Process

Emission Source/Control: PESV3 - Process

Emission Source/Control: PESV5 - Process

Emission Source/Control: PJORS - Process

Emission Source/Control: PKSDT - Process

Emission Source/Control: POLY1 - Process

Emission Source/Control: POLY2 - Process

Emission Source/Control: POLY3 - Process

Emission Source/Control: POLY5 - Process

Item 477.77(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 027

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #027, which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63, Subpart FFFF.

Emission Source/Control: 30LET - Process

Emission Source/Control: 30MTA - Process

Emission Source/Control: 30MTB - Process

Emission Source/Control: 30PT1 - Process

Emission Source/Control: 30PT2 - Process

Emission Source/Control: 30SLT - Process

Emission Source/Control: PESV1 - Process

Emission Source/Control: PESV2 - Process

Emission Source/Control: PESV3 - Process

Emission Source/Control: PESV5 - Process

Emission Source/Control: PJORS - Process



Emission Source/Control: PKSDT - Process

Emission Source/Control: POLY1 - Process

Emission Source/Control: POLY2 - Process

Emission Source/Control: POLY3 - Process

Emission Source/Control: POLY5 - Process

Item 477.78(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 031

Source Classification Code: 3-01-999-99

Process Description:

This process represents FOM 031, which is a miscellaneous organic chemical manufacturing unit (MCPU) that is regulated under 40 CFR Part 63, Subpart FFFF (Miscellaneous Organic Chemical Manufacturing).

Emission Source/Control: 30LET - Process

Emission Source/Control: 30MTA - Process

Emission Source/Control: 30MTB - Process

Emission Source/Control: 30PT1 - Process

Emission Source/Control: 30PT2 - Process

Emission Source/Control: 30SLT - Process

Emission Source/Control: PESV1 - Process

Emission Source/Control: PESV2 - Process

Emission Source/Control: PESV3 - Process

Emission Source/Control: PESV5 - Process

Emission Source/Control: PJORS - Process

Emission Source/Control: PKSDT - Process

Emission Source/Control: POLY1 - Process

Emission Source/Control: POLY2 - Process

Emission Source/Control: POLY3 - Process

Emission Source/Control: POLY5 - Process



Item 477.79(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 032

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #032, which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63, Subpart FFFF. This process operates out of buildings 30 and 78.

Emission Source/Control: 30LET - Process

Emission Source/Control: 30MTA - Process

Emission Source/Control: 30MTB - Process

Emission Source/Control: 30PT1 - Process

Emission Source/Control: 30PT2 - Process

Emission Source/Control: 30SLT - Process

Emission Source/Control: 78PK2 - Process

Emission Source/Control: 78VES - Process

Emission Source/Control: PESV1 - Process

Emission Source/Control: PESV2 - Process

Emission Source/Control: PESV3 - Process

Emission Source/Control: PESV5 - Process

Emission Source/Control: PJORS - Process

Emission Source/Control: PKSDT - Process

Emission Source/Control: POLY1 - Process

Emission Source/Control: POLY2 - Process

Emission Source/Control: POLY3 - Process

Emission Source/Control: POLY5 - Process

Item 477.80(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 033

Source Classification Code: 3-01-999-99



Process Description:

Equipment for Family of Material #033, which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63, Subpart FFFF. This process operates out of buildings 30 and 78.

Emission Source/Control: FBCS1 - Control
Control Type: PACKED-GAS ABSORPTION SYSTEM

Emission Source/Control: FBCS2 - Control
Control Type: PACKED-GAS ABSORPTION SYSTEM

Emission Source/Control: FBIAB - Control
Control Type: DIRECT FLAME AFTERBURNER

Emission Source/Control: FBIQU - Control
Control Type: SPRAY TOWER

Emission Source/Control: IWS11 - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS12 - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS1A - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS1B - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS1C - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS21 - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS22 - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS2A - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS2B - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS2C - Control
Control Type: WET SCRUBBER

Emission Source/Control: RKIAB - Control
Control Type: DIRECT FLAME AFTERBURNER

Emission Source/Control: RKICS - Control
Control Type: PACKED-GAS ABSORPTION SYSTEM



Emission Source/Control: RKIQU - Control
Control Type: SPRAY TOWER

Emission Source/Control: 30LET - Process

Emission Source/Control: 30MTA - Process

Emission Source/Control: 30MTB - Process

Emission Source/Control: 30PT1 - Process

Emission Source/Control: 30PT2 - Process

Emission Source/Control: 30SLT - Process

Emission Source/Control: D4CNB - Process

Emission Source/Control: D4CON - Process

Emission Source/Control: PESV1 - Process

Emission Source/Control: PESV2 - Process

Emission Source/Control: PESV3 - Process

Emission Source/Control: PESV5 - Process

Emission Source/Control: PJORS - Process

Emission Source/Control: PKSDT - Process

Emission Source/Control: POLY1 - Process

Emission Source/Control: POLY2 - Process

Emission Source/Control: POLY3 - Process

Emission Source/Control: POLY5 - Process

Emission Source/Control: WTVST - Process

Item 477.81(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 035

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #035, which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63, Subpart FFFF.

Emission Source/Control: FBCS1 - Control



Control Type: PACKED-GAS ABSORPTION SYSTEM

Emission Source/Control: FBCS2 - Control
Control Type: PACKED-GAS ABSORPTION SYSTEM

Emission Source/Control: FBIAB - Control
Control Type: DIRECT FLAME AFTERBURNER

Emission Source/Control: FBIQU - Control
Control Type: SPRAY TOWER

Emission Source/Control: IWS11 - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS12 - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS1A - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS1B - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS1C - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS21 - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS22 - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS2A - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS2B - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS2C - Control
Control Type: WET SCRUBBER

Emission Source/Control: RKIAB - Control
Control Type: DIRECT FLAME AFTERBURNER

Emission Source/Control: RKICS - Control
Control Type: PACKED-GAS ABSORPTION SYSTEM

Emission Source/Control: RKIQU - Control
Control Type: SPRAY TOWER

Emission Source/Control: 30LET - Process

Emission Source/Control: 30MTA - Process



Emission Source/Control: 30MTB - Process

Emission Source/Control: 30PT1 - Process

Emission Source/Control: 30PT2 - Process

Emission Source/Control: 30SLT - Process

Emission Source/Control: D4CNB - Process

Emission Source/Control: D4CON - Process

Emission Source/Control: PESV1 - Process

Emission Source/Control: PESV2 - Process

Emission Source/Control: PESV3 - Process

Emission Source/Control: PESV5 - Process

Emission Source/Control: PJORS - Process

Emission Source/Control: PKSDT - Process

Emission Source/Control: POLY1 - Process

Emission Source/Control: POLY2 - Process

Emission Source/Control: POLY3 - Process

Emission Source/Control: POLY5 - Process

Emission Source/Control: WTVST - Process

Item 477.82(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 036

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #036 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63, Subpart FFFF.

Emission Source/Control: 30LET - Process

Emission Source/Control: 30MTA - Process

Emission Source/Control: 30MTB - Process

Emission Source/Control: 30PT1 - Process



Emission Source/Control: 30PT2 - Process

Emission Source/Control: 30SLT - Process

Emission Source/Control: PESV1 - Process

Emission Source/Control: PESV2 - Process

Emission Source/Control: PESV3 - Process

Emission Source/Control: PESV5 - Process

Emission Source/Control: PJORS - Process

Emission Source/Control: PKSDT - Process

Emission Source/Control: POLY1 - Process

Emission Source/Control: POLY2 - Process

Emission Source/Control: POLY3 - Process

Emission Source/Control: POLY5 - Process

Item 477.83(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 037

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #037 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63, Subpart FFFF.

Emission Source/Control: 30LET - Process

Emission Source/Control: 30MTA - Process

Emission Source/Control: 30MTB - Process

Emission Source/Control: 30PT1 - Process

Emission Source/Control: 30PT2 - Process

Emission Source/Control: 30SLT - Process

Emission Source/Control: PESV1 - Process

Emission Source/Control: PESV2 - Process

Emission Source/Control: PESV3 - Process

Emission Source/Control: PESV5 - Process



Emission Source/Control: PJORS - Process

Emission Source/Control: PKSDT - Process

Emission Source/Control: POLY1 - Process

Emission Source/Control: POLY2 - Process

Emission Source/Control: POLY3 - Process

Emission Source/Control: POLY5 - Process

Item 477.84(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 039

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #039 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63, Subpart FFFF.

Emission Source/Control: 37AST - Process

Emission Source/Control: 37EJE - Process

Emission Source/Control: 37GPR - Process

Emission Source/Control: 37GWT - Process

Emission Source/Control: 37SSR - Process

Item 477.85(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 042

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #042 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63, Subpart FFFF. This process operates out of buildings 30 and 78.

Emission Source/Control: 30LET - Process

Emission Source/Control: 30MTA - Process

Emission Source/Control: 30SLT - Process

Emission Source/Control: 78HWV - Process

Emission Source/Control: 78MVS - Process



Emission Source/Control: 78PK2 - Process

Emission Source/Control: 78PK9 - Process

Emission Source/Control: 78PKV - Process

Emission Source/Control: 78VES - Process

Emission Source/Control: PESV6 - Process

Emission Source/Control: PESV7 - Process

Emission Source/Control: PESV8 - Process

Emission Source/Control: PJORS - Process

Emission Source/Control: PKSDT - Process

Emission Source/Control: POLY4 - Process

Emission Source/Control: POLY6 - Process

Emission Source/Control: POLY7 - Process

Emission Source/Control: POLY8 - Process

Item 477.86(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 043

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #043 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63, Subpart FFFF.

Emission Source/Control: 30LET - Process

Emission Source/Control: 30MTA - Process

Emission Source/Control: 30SLT - Process

Emission Source/Control: PESV6 - Process

Emission Source/Control: PESV7 - Process

Emission Source/Control: PESV8 - Process

Emission Source/Control: PJORS - Process

Emission Source/Control: PKSDT - Process



Emission Source/Control: POLY4 - Process

Emission Source/Control: POLY6 - Process

Emission Source/Control: POLY7 - Process

Emission Source/Control: POLY8 - Process

Item 477.87(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 045

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #045 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63, Subpart FFFF.

Emission Source/Control: 30LET - Process

Emission Source/Control: 30MTA - Process

Emission Source/Control: 30SLT - Process

Emission Source/Control: PESV6 - Process

Emission Source/Control: PESV7 - Process

Emission Source/Control: PESV8 - Process

Emission Source/Control: PJORS - Process

Emission Source/Control: PKSDT - Process

Emission Source/Control: POLY4 - Process

Emission Source/Control: POLY6 - Process

Emission Source/Control: POLY7 - Process

Emission Source/Control: POLY8 - Process

Item 477.88(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 046

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #046 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63, Subpart FFFF.

Emission Source/Control: 71FP1 - Process



Emission Source/Control: 71H2R - Process

Emission Source/Control: 71HES - Process

Emission Source/Control: 71VAC - Process

Item 477.89(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 048

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #048 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63, Subpart FFFF.

Emission Source/Control: 71FP1 - Process

Emission Source/Control: 71H2R - Process

Emission Source/Control: 71HES - Process

Emission Source/Control: 71VAC - Process

Item 477.90(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 049

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #049 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63, Subpart FFFF.

Emission Source/Control: 71HYS - Control
Control Type: WET SCRUBBER

Emission Source/Control: 71CR2 - Process

Emission Source/Control: 71CR7 - Process

Emission Source/Control: 71DS3 - Process

Emission Source/Control: 71FP1 - Process

Emission Source/Control: 71FP3 - Process

Emission Source/Control: 71H2R - Process

Emission Source/Control: 71HES - Process

Emission Source/Control: 71HTL - Process



Emission Source/Control: 71HY3 - Process

Emission Source/Control: 71SIL - Process

Emission Source/Control: 71SWT - Process

Emission Source/Control: 71VAC - Process

Item 477.91(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 051

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #051 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63, Subpart FFFF.

Emission Source/Control: 71HYS - Control

Control Type: WET SCRUBBER

Emission Source/Control: 71CR2 - Process

Emission Source/Control: 71CR7 - Process

Emission Source/Control: 71DS3 - Process

Emission Source/Control: 71FP1 - Process

Emission Source/Control: 71FP3 - Process

Emission Source/Control: 71H2R - Process

Emission Source/Control: 71HES - Process

Emission Source/Control: 71HY3 - Process

Emission Source/Control: 71SIL - Process

Emission Source/Control: 71SWT - Process

Emission Source/Control: 71VAC - Process

Item 477.92(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 054

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #054 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF.



Emission Source/Control: 71FP1 - Process

Emission Source/Control: 71H2R - Process

Emission Source/Control: 71HES - Process

Emission Source/Control: 71VAC - Process

Item 477.93(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 055

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #055 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF.

Emission Source/Control: 71FP1 - Process

Emission Source/Control: 71H2R - Process

Emission Source/Control: 71HES - Process

Emission Source/Control: 71VAC - Process

Item 477.94(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 061

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #061 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF.

Emission Source/Control: 32DMX - Process

Emission Source/Control: 32WTD - Process

Item 477.95(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 064

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #064 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF.

Emission Source/Control: 32DMX - Process



Emission Source/Control: 32WTD - Process

Item 477.96(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 072

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #072 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF.

Emission Source/Control: 71HYS - Control
Control Type: WET SCRUBBER

Emission Source/Control: 71CR1 - Process

Emission Source/Control: 71CR5 - Process

Emission Source/Control: 71CR8 - Process

Emission Source/Control: 71RT1 - Process

Emission Source/Control: 71RT2 - Process

Emission Source/Control: 71WT7 - Process

Item 477.97(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 073

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #073 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF. This process operates out of buildings 21 and 35.

Emission Source/Control: 35CSC - Control
Control Type: WET SCRUBBER

Emission Source/Control: 35CSS - Control
Control Type: WET SCRUBBER

Emission Source/Control: 2178C - Process

Emission Source/Control: 35CCE - Process

Emission Source/Control: 35CHW - Process

Emission Source/Control: 35CIV - Process

Emission Source/Control: 35CPH - Process



Emission Source/Control: 35CRV - Process

Emission Source/Control: 35CWS - Process

Emission Source/Control: 35DRV - Process

Emission Source/Control: 35SOT - Process

Emission Source/Control: 35WES - Process

Emission Source/Control: 59911 - Process

Emission Source/Control: 59912 - Process

Emission Source/Control: 59913 - Process

Emission Source/Control: ST570 - Process

Emission Source/Control: ST571 - Process

Emission Source/Control: T5994 - Process

Emission Source/Control: T5995 - Process

Emission Source/Control: T5996 - Process

Item 477.98(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 078

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #078 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF. This process operates out of buildings 23, 24 and 24A.

Emission Source/Control: 24GBF - Control

Control Type: GRAVEL BED FILTER

Emission Source/Control: FBCS1 - Control

Control Type: PACKED-GAS ABSORPTION SYSTEM

Emission Source/Control: FBCS2 - Control

Control Type: PACKED-GAS ABSORPTION SYSTEM

Emission Source/Control: FBIAB - Control

Control Type: DIRECT FLAME AFTERBURNER

Emission Source/Control: FBIQU - Control

Control Type: SPRAY TOWER



Emission Source/Control: IWS11 - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS12 - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS1A - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS1B - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS1C - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS21 - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS22 - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS2A - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS2B - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS2C - Control
Control Type: WET SCRUBBER

Emission Source/Control: RKIAB - Control
Control Type: DIRECT FLAME AFTERBURNER

Emission Source/Control: RKICS - Control
Control Type: PACKED-GAS ABSORPTION SYSTEM

Emission Source/Control: RKIQU - Control
Control Type: SPRAY TOWER

Emission Source/Control: 23SST - Process

Emission Source/Control: 23TST - Process

Emission Source/Control: 24BKC - Process

Emission Source/Control: 24BKR - Process

Emission Source/Control: 24DIC - Process

Emission Source/Control: 24FAK - Process

Emission Source/Control: 24HYD - Process



Emission Source/Control: 24IPL - Process

Emission Source/Control: 24KOH - Process

Emission Source/Control: 24PBT - Process

Emission Source/Control: 24PRE - Process

Emission Source/Control: 24PSS - Process

Emission Source/Control: 24RST - Process

Emission Source/Control: 24SIW - Process

Emission Source/Control: 24WSH - Process

Emission Source/Control: MTCSS - Process

Emission Source/Control: WTVST - Process

Item 477.99(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 084

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #084 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF.

Emission Source/Control: 37AST - Process

Emission Source/Control: 37EJV - Process

Emission Source/Control: 37GPR - Process

Emission Source/Control: 37GWT - Process

Emission Source/Control: 37SSR - Process

Item 477.100(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 086

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #086 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF.

Emission Source/Control: 372MD - Process

Emission Source/Control: 372MK - Process



Emission Source/Control: 374MD - Process

Emission Source/Control: 374MK - Process

Emission Source/Control: 37AST - Process

Emission Source/Control: 37EJV - Process

Emission Source/Control: 37FBP - Process

Emission Source/Control: 37FCS - Process

Emission Source/Control: 37GPR - Process

Emission Source/Control: 37GWT - Process

Emission Source/Control: 37PRV - Process

Emission Source/Control: 37SSR - Process

Emission Source/Control: 37TAN - Process

Emission Source/Control: 37TK8 - Process

Emission Source/Control: 37VAC - Process

Item 477.101(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 087

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #087 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF.

Emission Source/Control: 372MD - Process

Emission Source/Control: 372MK - Process

Emission Source/Control: 374MD - Process

Emission Source/Control: 374MK - Process

Emission Source/Control: 37D2M - Process

Emission Source/Control: 37FBP - Process

Emission Source/Control: 37FCS - Process

Emission Source/Control: 37PRV - Process



Emission Source/Control: 37TAN - Process

Emission Source/Control: 37TK8 - Process

Emission Source/Control: 37VAC - Process

Item 477.102(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 088

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #088 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF.

Emission Source/Control: 372MH - Process

Emission Source/Control: 37NHT - Process

Emission Source/Control: 37NTL - Process

Emission Source/Control: 37STF - Process

Item 477.103(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 094

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #094 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF.

Emission Source/Control: 37AST - Process

Emission Source/Control: 37EJV - Process

Emission Source/Control: 37GPR - Process

Emission Source/Control: 37GWT - Process

Emission Source/Control: 37SSR - Process

Item 477.104(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 095

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #095 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF.



Emission Source/Control: 71HYS - Control
Control Type: WET SCRUBBER

Emission Source/Control: 37AST - Process

Emission Source/Control: 37EJV - Process

Emission Source/Control: 37GPR - Process

Emission Source/Control: 37GWT - Process

Emission Source/Control: 37SSR - Process

Emission Source/Control: 71CR1 - Process

Emission Source/Control: 71CR5 - Process

Emission Source/Control: 71CR8 - Process

Emission Source/Control: 71RT1 - Process

Emission Source/Control: 71RT2 - Process

Emission Source/Control: 71WT7 - Process

Item 477.105(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 096

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #096 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF.

Emission Source/Control: 37ASB - Process

Emission Source/Control: 37EJE - Process

Emission Source/Control: 37EJV - Process

Emission Source/Control: 37MLE - Process

Emission Source/Control: 37RHE - Process

Emission Source/Control: 37RHH - Process

Emission Source/Control: RH502 - Process

Emission Source/Control: RHFTK - Process

Emission Source/Control: RHJOD - Process



Emission Source/Control: RHPTK - Process

Emission Source/Control: RHSTD - Process

Emission Source/Control: RHSTE - Process

Emission Source/Control: RHSTL - Process

Item 477.106(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 097

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #097 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF. This process operates out of buildings 30 and 78.

Emission Source/Control: 30LET - Process

Emission Source/Control: 30MTA - Process

Emission Source/Control: 30MTB - Process

Emission Source/Control: 30PT1 - Process

Emission Source/Control: 30PT2 - Process

Emission Source/Control: 30SLT - Process

Emission Source/Control: 78HWV - Process

Emission Source/Control: 78MVS - Process

Emission Source/Control: 78P14 - Process

Emission Source/Control: 78PK1 - Process

Emission Source/Control: 78PK2 - Process

Emission Source/Control: 78PKV - Process

Emission Source/Control: 78RVC - Process

Emission Source/Control: 78VES - Process

Emission Source/Control: PESV1 - Process

Emission Source/Control: PESV2 - Process

Emission Source/Control: PESV3 - Process



Emission Source/Control: PESV5 - Process

Emission Source/Control: PJORS - Process

Emission Source/Control: PKSDT - Process

Emission Source/Control: POLY1 - Process

Emission Source/Control: POLY2 - Process

Emission Source/Control: POLY3 - Process

Emission Source/Control: POLY5 - Process

Item 477.107(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 099

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #099 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF.

Emission Source/Control: 78HWV - Process

Emission Source/Control: 78MVS - Process

Emission Source/Control: 78PK2 - Process

Emission Source/Control: 78PK9 - Process

Emission Source/Control: 78PKV - Process

Emission Source/Control: 78VES - Process

Item 477.108(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 100

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #100 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF.

Emission Source/Control: 37BDC - Control
Control Type: FABRIC FILTER

Emission Source/Control: 36ST4 - Process

Emission Source/Control: 374MP - Process



Emission Source/Control: 37APV - Process
Emission Source/Control: 37BDD - Process
Emission Source/Control: 37CE1 - Process
Emission Source/Control: 37CE2 - Process
Emission Source/Control: 37CHT - Process
Emission Source/Control: 37CRC - Process
Emission Source/Control: 37CST - Process
Emission Source/Control: 37D4F - Process
Emission Source/Control: 37FAT - Process
Emission Source/Control: 37FEF - Process
Emission Source/Control: 37FTL - Process
Emission Source/Control: 37GV1 - Process
Emission Source/Control: 37MLE - Process
Emission Source/Control: 37NHT - Process
Emission Source/Control: 37ST2 - Process
Emission Source/Control: 37ST3 - Process
Emission Source/Control: 37ST7 - Process
Emission Source/Control: 37ST8 - Process
Emission Source/Control: 37ST9 - Process
Emission Source/Control: 37STA - Process
Emission Source/Control: 37STB - Process
Emission Source/Control: 37STC - Process
Emission Source/Control: 37TA2 - Process
Emission Source/Control: 37TA3 - Process
Emission Source/Control: 37VAC - Process
Emission Source/Control: 37VCU - Process



Emission Source/Control: 37VSS - Process

Item 477.109(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 101

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #101 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF.

Emission Source/Control: 71HYS - Control
Control Type: WET SCRUBBER

Emission Source/Control: 71CR1 - Process

Emission Source/Control: 71CR2 - Process

Emission Source/Control: 71CR5 - Process

Emission Source/Control: 71CR7 - Process

Emission Source/Control: 71CR8 - Process

Emission Source/Control: 71HY3 - Process

Emission Source/Control: 71RT1 - Process

Emission Source/Control: 71RT2 - Process

Emission Source/Control: 71SIL - Process

Emission Source/Control: 71SWT - Process

Emission Source/Control: 71WT7 - Process

Item 477.110(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 102

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #101 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF. This process operates out of buildings 30 and 71.

Emission Source/Control: 1MHSC - Control
Control Type: WET SCRUBBER

Emission Source/Control: 71HYS - Control
Control Type: WET SCRUBBER



Emission Source/Control: 30LET - Process

Emission Source/Control: 30MTA - Process

Emission Source/Control: 30MTB - Process

Emission Source/Control: 30PT1 - Process

Emission Source/Control: 30PT2 - Process

Emission Source/Control: 30SLT - Process

Emission Source/Control: 71CR1 - Process

Emission Source/Control: 71CR5 - Process

Emission Source/Control: 71CR8 - Process

Emission Source/Control: 71FP1 - Process

Emission Source/Control: 71H2R - Process

Emission Source/Control: 71HES - Process

Emission Source/Control: 71RT1 - Process

Emission Source/Control: 71RT2 - Process

Emission Source/Control: 71VAC - Process

Emission Source/Control: 71WT7 - Process

Emission Source/Control: PESV1 - Process

Emission Source/Control: PESV2 - Process

Emission Source/Control: PESV3 - Process

Emission Source/Control: PESV5 - Process

Emission Source/Control: PJORS - Process

Emission Source/Control: PKSDT - Process

Emission Source/Control: POLY1 - Process

Emission Source/Control: POLY2 - Process

Emission Source/Control: POLY3 - Process

Emission Source/Control: POLY5 - Process



Item 477.111(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 103

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #103 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF.

Emission Source/Control: 1MHSC - Control

Control Type: WET SCRUBBER

Emission Source/Control: 71HYS - Control

Control Type: WET SCRUBBER

Emission Source/Control: 71CR1 - Process

Emission Source/Control: 71CR5 - Process

Emission Source/Control: 71CR8 - Process

Emission Source/Control: 71FP1 - Process

Emission Source/Control: 71HES - Process

Emission Source/Control: 71HZR - Process

Emission Source/Control: 71RT1 - Process

Emission Source/Control: 71RT2 - Process

Emission Source/Control: 71VAC - Process

Emission Source/Control: 71WT7 - Process

Item 477.112(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 105

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #105 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF.

Emission Source/Control: 30LET - Process

Emission Source/Control: 30MTA - Process

Emission Source/Control: 30MTB - Process

Emission Source/Control: 30PT1 - Process



Emission Source/Control: 30PT2 - Process

Emission Source/Control: 30SLT - Process

Emission Source/Control: PESV1 - Process

Emission Source/Control: PESV2 - Process

Emission Source/Control: PESV3 - Process

Emission Source/Control: PESV5 - Process

Emission Source/Control: PJORS - Process

Emission Source/Control: PKSDT - Process

Emission Source/Control: POLY1 - Process

Emission Source/Control: POLY2 - Process

Emission Source/Control: POLY3 - Process

Emission Source/Control: POLY5 - Process

Item 477.113(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 109

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #109 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF.

Emission Source/Control: 372MD - Process

Emission Source/Control: 372MK - Process

Emission Source/Control: 374MD - Process

Emission Source/Control: 374MK - Process

Emission Source/Control: 37AST - Process

Emission Source/Control: 37EJV - Process

Emission Source/Control: 37FBP - Process

Emission Source/Control: 37FCS - Process

Emission Source/Control: 37GPR - Process



Emission Source/Control: 37GWT - Process

Emission Source/Control: 37PRV - Process

Emission Source/Control: 37SSR - Process

Emission Source/Control: 37TAN - Process

Emission Source/Control: 37VAC - Process

Item 477.114(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 114

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #114 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF.

Emission Source/Control: 374MP - Process

Emission Source/Control: 37FST - Process

Emission Source/Control: 37KOT - Process

Emission Source/Control: 37MST - Process
Design Capacity: 10,000 gallons

Emission Source/Control: 37P15 - Process

Emission Source/Control: 37PSR - Process

Emission Source/Control: 37PUR - Process

Emission Source/Control: 37TK8 - Process

Item 477.115(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 115

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #115 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF. This process operates out of buildings 23, 24 and 24A.

Emission Source/Control: 23SCR - Control
Control Type: WET SCRUBBER

Emission Source/Control: FBCS1 - Control
Control Type: PACKED-GAS ABSORPTION SYSTEM



Emission Source/Control: FBCS2 - Control
Control Type: PACKED-GAS ABSORPTION SYSTEM

Emission Source/Control: FBIAB - Control
Control Type: DIRECT FLAME AFTERBURNER

Emission Source/Control: FBIQU - Control
Control Type: SPRAY TOWER

Emission Source/Control: IWS11 - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS12 - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS1A - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS1B - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS1C - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS21 - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS22 - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS2A - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS2B - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS2C - Control
Control Type: WET SCRUBBER

Emission Source/Control: RKIAB - Control
Control Type: DIRECT FLAME AFTERBURNER

Emission Source/Control: RKICS - Control
Control Type: PACKED-GAS ABSORPTION SYSTEM

Emission Source/Control: RKIQU - Control
Control Type: SPRAY TOWER

Emission Source/Control: 23BT1 - Process

Emission Source/Control: 23BT2 - Process



Process Description:

Equipment for Family of Material #117 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF.

Emission Source/Control: 71HYS - Control
Control Type: WET SCRUBBER

Emission Source/Control: 71CR1 - Process

Emission Source/Control: 71CR5 - Process

Emission Source/Control: 71CR8 - Process

Emission Source/Control: 71RT1 - Process

Emission Source/Control: 71RT2 - Process

Emission Source/Control: 71WT7 - Process

Item 477.118(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 120

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #120 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF.

Emission Source/Control: 1MHSC - Control
Control Type: WET SCRUBBER

Emission Source/Control: 71HYS - Control
Control Type: WET SCRUBBER

Emission Source/Control: 71CR1 - Process

Emission Source/Control: 71CR5 - Process

Emission Source/Control: 71CR8 - Process

Emission Source/Control: 71FP1 - Process

Emission Source/Control: 71HES - Process

Emission Source/Control: 71HZR - Process

Emission Source/Control: 71RT1 - Process

Emission Source/Control: 71RT2 - Process

Emission Source/Control: 71VAC - Process



Emission Source/Control: 71WT7 - Process

Item 477.119(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 121

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #121 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF.

Emission Source/Control: 374MP - Process

Emission Source/Control: 374ST - Process

Emission Source/Control: 37750 - Process

Emission Source/Control: 37GW7 - Process

Emission Source/Control: 37PRV - Process

Emission Source/Control: 37PSR - Process

Item 477.120(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 122

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #122 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF.

Emission Source/Control: 374MP - Process

Emission Source/Control: 374ST - Process

Emission Source/Control: 37750 - Process

Emission Source/Control: 37GW7 - Process

Emission Source/Control: 37PRV - Process

Emission Source/Control: 37PSR - Process

Item 477.121(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 124

Source Classification Code: 3-01-999-99

Process Description:



Equipment for Family of Material #124 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF.

Emission Source/Control: 37AST - Process

Emission Source/Control: 37EJV - Process

Emission Source/Control: 37GPR - Process

Emission Source/Control: 37GWT - Process

Emission Source/Control: 37SSR - Process

Item 477.122(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 125

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #125 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF.

Emission Source/Control: 374MP - Process

Emission Source/Control: 374ST - Process

Emission Source/Control: 37750 - Process

Emission Source/Control: 37GW7 - Process

Emission Source/Control: 37PRV - Process

Emission Source/Control: 37PSR - Process

Item 477.123(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 127

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #127 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF.

Emission Source/Control: 37AST - Process

Emission Source/Control: 37EJV - Process

Emission Source/Control: 37GPR - Process

Emission Source/Control: 37GWT - Process



Emission Source/Control: 37SSR - Process

Item 477.124(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 129

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #129 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF.

Emission Source/Control: 374MP - Process

Emission Source/Control: 37FST - Process

Emission Source/Control: 37KOT - Process

Emission Source/Control: 37MST - Process

Design Capacity: 10,000 gallons

Emission Source/Control: 37P15 - Process

Emission Source/Control: 37PSR - Process

Emission Source/Control: 37PUR - Process

Emission Source/Control: 37TK8 - Process

Item 477.125(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 130

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #130 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF.

Emission Source/Control: 37AST - Process

Emission Source/Control: 37EJV - Process

Emission Source/Control: 37GPR - Process

Emission Source/Control: 37GWT - Process

Emission Source/Control: 37SSR - Process

Item 477.126(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:



Emission Unit: C-27018

Process: 131

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #131 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF.

Emission Source/Control: 78HWV - Process

Emission Source/Control: 78MVS - Process

Emission Source/Control: 78PK9 - Process

Emission Source/Control: 78PKV - Process

Emission Source/Control: 78RVC - Process

Item 477.127(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 132

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #132 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF.

Emission Source/Control: 78HWV - Process

Emission Source/Control: 78MVS - Process

Emission Source/Control: 78PK9 - Process

Emission Source/Control: 78PKV - Process

Emission Source/Control: 78RVC - Process

Item 477.128(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 133

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #133 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF.

Emission Source/Control: 78FEH - Process

Emission Source/Control: 78FSC - Process

Item 477.129(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:



Emission Unit: C-27018

Process: 134

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #134 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF.

Emission Source/Control: 78P14 - Process

Emission Source/Control: 78PK1 - Process

Emission Source/Control: 78VES - Process

Item 477.130(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 137

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #137 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF.

Emission Source/Control: 31DB1 - Control
Control Type: FABRIC FILTER

Emission Source/Control: 31DB2 - Control
Control Type: FABRIC FILTER

Emission Source/Control: 302GD - Process

Emission Source/Control: 305GD - Process

Emission Source/Control: 30BKM - Process

Emission Source/Control: 31LKR - Process

Emission Source/Control: 31LTS - Process

Emission Source/Control: 31STH - Process

Item 477.131(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 139

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #139 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF.

Emission Source/Control: 31DB2 - Control



Control Type: FABRIC FILTER

Emission Source/Control: 31DC1 - Control
Control Type: REFRIGERATED CONDENSER

Emission Source/Control: 31DC2 - Control
Control Type: REFRIGERATED CONDENSER

Emission Source/Control: 31DMS - Control
Control Type: WET SCRUBBER

Emission Source/Control: 31FS1 - Control
Control Type: WET SCRUBBER

Emission Source/Control: 31630 - Process

Emission Source/Control: 31AS6 - Process

Emission Source/Control: 31ESB - Process

Emission Source/Control: 31FKR - Process

Emission Source/Control: 31FP1 - Process

Emission Source/Control: 31FP2 - Process

Emission Source/Control: 31FP3 - Process

Emission Source/Control: 31FS2 - Process

Emission Source/Control: 31GHV - Process

Emission Source/Control: 31LKR - Process

Emission Source/Control: 31LNM - Process

Emission Source/Control: 31LSM - Process

Emission Source/Control: 31LTS - Process

Emission Source/Control: 31NAS - Process

Emission Source/Control: 31NBH - Process

Emission Source/Control: 31PDR - Process

Emission Source/Control: 31RSR - Process

Emission Source/Control: 31SAS - Process

Emission Source/Control: 31SFB - Process

Emission Source/Control: 31STH - Process



Emission Source/Control: 31WSB - Process

Emission Source/Control: DRSTK - Process

Item 477.132(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 141

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #141 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF.

Emission Source/Control: 30LET - Process

Emission Source/Control: 30MTA - Process

Emission Source/Control: 30MTB - Process

Emission Source/Control: 30PT1 - Process

Emission Source/Control: 30PT2 - Process

Emission Source/Control: 30SLT - Process

Emission Source/Control: DRSTK - Process

Emission Source/Control: PESV1 - Process

Emission Source/Control: PESV2 - Process

Emission Source/Control: PESV3 - Process

Emission Source/Control: PESV5 - Process

Emission Source/Control: PJORS - Process

Emission Source/Control: PKSDT - Process

Emission Source/Control: POLY1 - Process

Emission Source/Control: POLY2 - Process

Emission Source/Control: POLY3 - Process

Emission Source/Control: POLY5 - Process

Item 477.133(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018



Process: 142

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #142 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF.

Emission Source/Control: 31DB2 - Control
Control Type: FABRIC FILTER

Emission Source/Control: 31DC1 - Control
Control Type: REFRIGERATED CONDENSER

Emission Source/Control: 31DC2 - Control
Control Type: REFRIGERATED CONDENSER

Emission Source/Control: 31DMS - Control
Control Type: WET SCRUBBER

Emission Source/Control: 31FS1 - Control
Control Type: WET SCRUBBER

Emission Source/Control: 31630 - Process

Emission Source/Control: 31AS6 - Process

Emission Source/Control: 31ESB - Process

Emission Source/Control: 31FKR - Process

Emission Source/Control: 31FP1 - Process

Emission Source/Control: 31FP2 - Process

Emission Source/Control: 31FP3 - Process

Emission Source/Control: 31FS2 - Process

Emission Source/Control: 31GHV - Process

Emission Source/Control: 31LNM - Process

Emission Source/Control: 31LSM - Process

Emission Source/Control: 31LTS - Process

Emission Source/Control: 31NAS - Process

Emission Source/Control: 31NBH - Process

Emission Source/Control: 31PDR - Process

Emission Source/Control: 31RSR - Process



Emission Source/Control: 31SAS - Process

Emission Source/Control: 31SFB - Process

Emission Source/Control: 31STH - Process

Emission Source/Control: 31WSB - Process

Emission Source/Control: DRSTK - Process

Item 477.134(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 143

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #143 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF.

Emission Source/Control: FBCS1 - Control

Control Type: PACKED-GAS ABSORPTION SYSTEM

Emission Source/Control: FBCS2 - Control

Control Type: PACKED-GAS ABSORPTION SYSTEM

Emission Source/Control: FBIAB - Control

Control Type: DIRECT FLAME AFTERBURNER

Emission Source/Control: FBIQU - Control

Control Type: SPRAY TOWER

Emission Source/Control: IWS11 - Control

Control Type: WET SCRUBBER

Emission Source/Control: IWS12 - Control

Control Type: WET SCRUBBER

Emission Source/Control: IWS1A - Control

Control Type: WET SCRUBBER

Emission Source/Control: IWS1B - Control

Control Type: WET SCRUBBER

Emission Source/Control: IWS1C - Control

Control Type: WET SCRUBBER

Emission Source/Control: IWS21 - Control

Control Type: WET SCRUBBER

Emission Source/Control: IWS22 - Control

Control Type: WET SCRUBBER



Emission Source/Control: IWS2A - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS2B - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS2C - Control
Control Type: WET SCRUBBER

Emission Source/Control: RKIAB - Control
Control Type: DIRECT FLAME AFTERBURNER

Emission Source/Control: RKICS - Control
Control Type: PACKED-GAS ABSORPTION SYSTEM

Emission Source/Control: RKIQU - Control
Control Type: SPRAY TOWER

Emission Source/Control: 30LET - Process

Emission Source/Control: 30MTA - Process

Emission Source/Control: 30MTB - Process

Emission Source/Control: 30PT1 - Process

Emission Source/Control: 30PT2 - Process

Emission Source/Control: 30SLT - Process

Emission Source/Control: D4CNB - Process

Emission Source/Control: D4CON - Process

Emission Source/Control: DRSTK - Process

Emission Source/Control: MTCSS - Process

Emission Source/Control: PESV1 - Process

Emission Source/Control: PESV2 - Process

Emission Source/Control: PESV3 - Process

Emission Source/Control: PESV5 - Process

Emission Source/Control: PJORS - Process

Emission Source/Control: PKSDT - Process

Emission Source/Control: POLY1 - Process

Emission Source/Control: POLY2 - Process



Emission Source/Control: POLY3 - Process

Emission Source/Control: POLY5 - Process

Emission Source/Control: WTVST - Process

Item 477.135(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 146

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #146 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF.

Emission Source/Control: 31DB1 - Control

Control Type: FABRIC FILTER

Emission Source/Control: 31DB2 - Control

Control Type: FABRIC FILTER

Emission Source/Control: 302GD - Process

Emission Source/Control: 305GD - Process

Emission Source/Control: 30BKM - Process

Emission Source/Control: 31LKR - Process

Emission Source/Control: 31LTS - Process

Emission Source/Control: 31STH - Process

Emission Source/Control: DRSTK - Process

Item 477.136(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 148

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #148 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF.

Emission Source/Control: 30LET - Process

Emission Source/Control: 30MTA - Process

Emission Source/Control: 30MTB - Process



Emission Source/Control: 30PT1 - Process

Emission Source/Control: 30PT2 - Process

Emission Source/Control: 30SLT - Process

Emission Source/Control: PESV1 - Process

Emission Source/Control: PESV2 - Process

Emission Source/Control: PESV3 - Process

Emission Source/Control: PESV5 - Process

Emission Source/Control: PJORS - Process

Emission Source/Control: PKSDT - Process

Emission Source/Control: POLY1 - Process

Emission Source/Control: POLY2 - Process

Emission Source/Control: POLY3 - Process

Emission Source/Control: POLY5 - Process

Item 477.137(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 149

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #149 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF.

Emission Source/Control: 30LET - Process

Emission Source/Control: 30MTA - Process

Emission Source/Control: 30MTB - Process

Emission Source/Control: 30PT1 - Process

Emission Source/Control: 30PT2 - Process

Emission Source/Control: 30SLT - Process

Emission Source/Control: PESV1 - Process

Emission Source/Control: PESV2 - Process

Emission Source/Control: PESV3 - Process



Emission Source/Control: PESV5 - Process

Emission Source/Control: PJORS - Process

Emission Source/Control: PKSDT - Process

Emission Source/Control: POLY1 - Process

Emission Source/Control: POLY2 - Process

Emission Source/Control: POLY3 - Process

Emission Source/Control: POLY5 - Process

Item 477.138(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 151

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #151 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF.

Emission Source/Control: 1MHSC - Control
Control Type: WET SCRUBBER

Emission Source/Control: 71HYS - Control
Control Type: WET SCRUBBER

Emission Source/Control: 71CR1 - Process

Emission Source/Control: 71CR5 - Process

Emission Source/Control: 71CR8 - Process

Emission Source/Control: 71FP1 - Process

Emission Source/Control: 71HES - Process

Emission Source/Control: 71HZR - Process

Emission Source/Control: 71RT1 - Process

Emission Source/Control: 71RT2 - Process

Emission Source/Control: 71VAC - Process

Emission Source/Control: 71WT7 - Process

Item 477.139(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:



Emission Unit: C-27018

Process: 152

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #152 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF.

Emission Source/Control: 1MHSC - Control

Control Type: WET SCRUBBER

Emission Source/Control: 71HYS - Control

Control Type: WET SCRUBBER

Emission Source/Control: 71CR2 - Process

Emission Source/Control: 71CR7 - Process

Emission Source/Control: 71DS3 - Process

Emission Source/Control: 71FP1 - Process

Emission Source/Control: 71FP3 - Process

Emission Source/Control: 71HES - Process

Emission Source/Control: 71HY3 - Process

Emission Source/Control: 71HZR - Process

Emission Source/Control: 71RT2 - Process

Emission Source/Control: 71SIL - Process

Emission Source/Control: 71SWT - Process

Emission Source/Control: 71VAC - Process

Item 477.140(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 154

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #154 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF.

Emission Source/Control: 71HYS - Control

Control Type: WET SCRUBBER

Emission Source/Control: 71CR1 - Process



Emission Source/Control: 71CR5 - Process

Emission Source/Control: 71CR8 - Process

Emission Source/Control: 71RT1 - Process

Emission Source/Control: 71RT2 - Process

Emission Source/Control: 71WT7 - Process

Item 477.141(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 156

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #156 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF.

Emission Source/Control: 71HYS - Control
Control Type: WET SCRUBBER

Emission Source/Control: 71CR2 - Process

Emission Source/Control: 71CR7 - Process

Emission Source/Control: 71DS3 - Process

Emission Source/Control: 71FP3 - Process

Emission Source/Control: 71HY3 - Process

Emission Source/Control: 71SIL - Process

Emission Source/Control: 71SWT - Process

Item 477.142(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 160

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #160 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF.

Emission Source/Control: 30LET - Process

Emission Source/Control: 30MTA - Process

Emission Source/Control: 30MTB - Process



Emission Source/Control: 30PT1 - Process

Emission Source/Control: 30PT2 - Process

Emission Source/Control: 30SLT - Process

Emission Source/Control: PESV1 - Process

Emission Source/Control: PESV2 - Process

Emission Source/Control: PESV3 - Process

Emission Source/Control: PESV5 - Process

Emission Source/Control: PJORS - Process

Emission Source/Control: PKSDT - Process

Emission Source/Control: POLY1 - Process

Emission Source/Control: POLY2 - Process

Emission Source/Control: POLY3 - Process

Emission Source/Control: POLY5 - Process

Item 477.143(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 161

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #161 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF.

Emission Source/Control: 30LET - Process

Emission Source/Control: 30MTA - Process

Emission Source/Control: 30MTB - Process

Emission Source/Control: 30PT1 - Process

Emission Source/Control: 30PT2 - Process

Emission Source/Control: 30SLT - Process

Emission Source/Control: PESV1 - Process

Emission Source/Control: PESV2 - Process

Emission Source/Control: PESV3 - Process



Emission Source/Control: PESV5 - Process

Emission Source/Control: PJORS - Process

Emission Source/Control: PKSDT - Process

Emission Source/Control: POLY1 - Process

Emission Source/Control: POLY2 - Process

Emission Source/Control: POLY3 - Process

Emission Source/Control: POLY5 - Process

Item 477.144(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 162

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #162 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF. This process operates out of buildings 30 and 78.

Emission Source/Control: 30LET - Process

Emission Source/Control: 30MTA - Process

Emission Source/Control: 30MTB - Process

Emission Source/Control: 30PT1 - Process

Emission Source/Control: 30PT2 - Process

Emission Source/Control: 30SLT - Process

Emission Source/Control: 78HWV - Process

Emission Source/Control: 78MVS - Process

Emission Source/Control: 78P14 - Process

Emission Source/Control: 78PK1 - Process

Emission Source/Control: 78PK2 - Process

Emission Source/Control: 78PKV - Process

Emission Source/Control: 78RVC - Process

Emission Source/Control: 78TR2 - Process



Emission Source/Control: 78VES - Process

Emission Source/Control: PESV1 - Process

Emission Source/Control: PESV2 - Process

Emission Source/Control: PESV3 - Process

Emission Source/Control: PESV5 - Process

Emission Source/Control: PJORS - Process

Emission Source/Control: PKSDT - Process

Emission Source/Control: POLY1 - Process

Emission Source/Control: POLY2 - Process

Emission Source/Control: POLY3 - Process

Emission Source/Control: POLY5 - Process

Item 477.145(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 163

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #163 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF.

Emission Source/Control: 30LET - Process

Emission Source/Control: 30MTA - Process

Emission Source/Control: 30MTB - Process

Emission Source/Control: 30PT1 - Process

Emission Source/Control: 30PT2 - Process

Emission Source/Control: 30SLT - Process

Emission Source/Control: PESV1 - Process

Emission Source/Control: PESV2 - Process

Emission Source/Control: PESV3 - Process

Emission Source/Control: PESV5 - Process



Emission Source/Control: PJORS - Process

Emission Source/Control: PKS DT - Process

Emission Source/Control: POLY1 - Process

Emission Source/Control: POLY2 - Process

Emission Source/Control: POLY3 - Process

Emission Source/Control: POLY5 - Process

Item 477.146(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 164

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #164 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF.

Emission Source/Control: 1MHSC - Control
Control Type: WET SCRUBBER

Emission Source/Control: 71HYS - Control
Control Type: WET SCRUBBER

Emission Source/Control: 71CR1 - Process

Emission Source/Control: 71CR5 - Process

Emission Source/Control: 71CR8 - Process

Emission Source/Control: 71FP1 - Process

Emission Source/Control: 71HES - Process

Emission Source/Control: 71HZR - Process

Emission Source/Control: 71RT1 - Process

Emission Source/Control: 71RT2 - Process

Emission Source/Control: 71VAC - Process

Emission Source/Control: 71WT7 - Process

Item 477.147(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 166

Source Classification Code: 3-01-999-99



Process Description:

Equipment for Family of Material #166 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF.

Emission Source/Control: 37BDC - Control
Control Type: FABRIC FILTER

Emission Source/Control: 36ST4 - Process

Emission Source/Control: 374MP - Process

Emission Source/Control: 37APV - Process

Emission Source/Control: 37BDD - Process

Emission Source/Control: 37CE1 - Process

Emission Source/Control: 37CE2 - Process

Emission Source/Control: 37CHT - Process

Emission Source/Control: 37CRC - Process

Emission Source/Control: 37CST - Process

Emission Source/Control: 37D4F - Process

Emission Source/Control: 37FAT - Process

Emission Source/Control: 37FEF - Process

Emission Source/Control: 37FTL - Process

Emission Source/Control: 37GV1 - Process

Emission Source/Control: 37MLE - Process

Emission Source/Control: 37NHT - Process

Emission Source/Control: 37ST2 - Process

Emission Source/Control: 37ST3 - Process

Emission Source/Control: 37ST7 - Process

Emission Source/Control: 37ST8 - Process

Emission Source/Control: 37ST9 - Process

Emission Source/Control: 37STA - Process

Emission Source/Control: 37STB - Process



Emission Source/Control: 37STC - Process

Emission Source/Control: 37TA2 - Process

Emission Source/Control: 37TA3 - Process

Emission Source/Control: 37VAC - Process

Emission Source/Control: 37VCU - Process

Emission Source/Control: 37VSS - Process

Item 477.148(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 172

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #172 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF.

Emission Source/Control: 37ASB - Process

Emission Source/Control: 37EJE - Process

Emission Source/Control: 37EJV - Process

Emission Source/Control: 37MLE - Process

Emission Source/Control: 37RHE - Process

Emission Source/Control: 37RHH - Process

Emission Source/Control: RH502 - Process

Emission Source/Control: RHFTK - Process

Emission Source/Control: RHJOD - Process

Emission Source/Control: RHPTK - Process

Emission Source/Control: RHSTD - Process

Emission Source/Control: RHSTE - Process

Emission Source/Control: RHSTL - Process

Item 477.149(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018



Process: 183 Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #183 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF.

Emission Source/Control: DMXV5 - Control
Control Type: VAPOR RECOVERY SYS(INCL.
CONDENSERS,HOODING, OTHER ENCLOSURES)

Emission Source/Control: DMXV6 - Control
Control Type: VAPOR RECOVERY SYS(INCL.
CONDENSERS,HOODING, OTHER ENCLOSURES)

Emission Source/Control: DMXV7 - Control
Control Type: VAPOR RECOVERY SYS(INCL.
CONDENSERS,HOODING, OTHER ENCLOSURES)

Emission Source/Control: DMXV8 - Control
Control Type: VAPOR RECOVERY SYS(INCL.
CONDENSERS,HOODING, OTHER ENCLOSURES)

Emission Source/Control: DMXV9 - Control
Control Type: VAPOR RECOVERY SYS(INCL.
CONDENSERS,HOODING, OTHER ENCLOSURES)

Emission Source/Control: 32DMX - Process

Emission Source/Control: 32WTD - Process

Item 477.150(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 184 Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #184 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF.

Emission Source/Control: 37BDC - Control
Control Type: FABRIC FILTER

Emission Source/Control: 36ST4 - Process

Emission Source/Control: 374MP - Process

Emission Source/Control: 37APV - Process

Emission Source/Control: 37BDD - Process

Emission Source/Control: 37CE1 - Process



- Emission Source/Control: 37CE2 - Process
- Emission Source/Control: 37CHT - Process
- Emission Source/Control: 37CRC - Process
- Emission Source/Control: 37CRE - Process
- Emission Source/Control: 37CST - Process
- Emission Source/Control: 37D4F - Process
- Emission Source/Control: 37FAT - Process
- Emission Source/Control: 37FEF - Process
- Emission Source/Control: 37FTL - Process
- Emission Source/Control: 37GV1 - Process
- Emission Source/Control: 37MLE - Process
- Emission Source/Control: 37NHT - Process
- Emission Source/Control: 37ST2 - Process
- Emission Source/Control: 37ST3 - Process
- Emission Source/Control: 37ST7 - Process
- Emission Source/Control: 37ST8 - Process
- Emission Source/Control: 37ST9 - Process
- Emission Source/Control: 37STA - Process
- Emission Source/Control: 37STB - Process
- Emission Source/Control: 37STC - Process
- Emission Source/Control: 37TA2 - Process
- Emission Source/Control: 37TA3 - Process
- Emission Source/Control: 37VAC - Process
- Emission Source/Control: 37VCU - Process
- Emission Source/Control: 37VSS - Process

Item 477.151(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:



Emission Unit: C-27018

Process: 185

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #185 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF.

Emission Source/Control: 1MHSC - Control

Control Type: WET SCRUBBER

Emission Source/Control: 71HYS - Control

Control Type: WET SCRUBBER

Emission Source/Control: 71CR1 - Process

Emission Source/Control: 71CR5 - Process

Emission Source/Control: 71CR8 - Process

Emission Source/Control: 71FP1 - Process

Emission Source/Control: 71HES - Process

Emission Source/Control: 71HZR - Process

Emission Source/Control: 71RT1 - Process

Emission Source/Control: 71RT2 - Process

Emission Source/Control: 71VAC - Process

Emission Source/Control: 71WT7 - Process

Item 477.152(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 186

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #186 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF.

Emission Source/Control: 30LET - Process

Emission Source/Control: 30MTA - Process

Emission Source/Control: 30MTB - Process

Emission Source/Control: 30PT1 - Process

Emission Source/Control: 30PT2 - Process



Emission Source/Control: 30SLT - Process

Emission Source/Control: PESV1 - Process

Emission Source/Control: PESV2 - Process

Emission Source/Control: PESV3 - Process

Emission Source/Control: PESV5 - Process

Emission Source/Control: PJORS - Process

Emission Source/Control: PKSDT - Process

Emission Source/Control: POLY1 - Process

Emission Source/Control: POLY2 - Process

Emission Source/Control: POLY3 - Process

Emission Source/Control: POLY5 - Process

Item 477.153(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 187

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #187 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF.

Emission Source/Control: 30LET - Process

Emission Source/Control: 30MTA - Process

Emission Source/Control: 30MTB - Process

Emission Source/Control: 30PT1 - Process

Emission Source/Control: 30PT2 - Process

Emission Source/Control: 30SLT - Process

Emission Source/Control: PESV1 - Process

Emission Source/Control: PESV2 - Process

Emission Source/Control: PESV3 - Process

Emission Source/Control: PESV5 - Process

Emission Source/Control: PJORS - Process



Emission Source/Control: PKSDT - Process

Emission Source/Control: POLY1 - Process

Emission Source/Control: POLY2 - Process

Emission Source/Control: POLY3 - Process

Emission Source/Control: POLY5 - Process

Item 477.154(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 188

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #188 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF.

Emission Source/Control: 31DB2 - Control

Control Type: FABRIC FILTER

Emission Source/Control: 31DC1 - Control

Control Type: REFRIGERATED CONDENSER

Emission Source/Control: 31DC2 - Control

Control Type: REFRIGERATED CONDENSER

Emission Source/Control: 31DMS - Control

Control Type: WET SCRUBBER

Emission Source/Control: 31FS1 - Control

Control Type: WET SCRUBBER

Emission Source/Control: 31630 - Process

Emission Source/Control: 31AS6 - Process

Emission Source/Control: 31ESB - Process

Emission Source/Control: 31FKR - Process

Emission Source/Control: 31FP1 - Process

Emission Source/Control: 31FP2 - Process

Emission Source/Control: 31FP3 - Process

Emission Source/Control: 31FS2 - Process

Emission Source/Control: 31GHV - Process



Emission Source/Control: 31LKR - Process

Emission Source/Control: 31LNM - Process

Emission Source/Control: 31LSM - Process

Emission Source/Control: 31LTS - Process

Emission Source/Control: 31NAS - Process

Emission Source/Control: 31NBH - Process

Emission Source/Control: 31PDR - Process

Emission Source/Control: 31RSR - Process

Emission Source/Control: 31SAS - Process

Emission Source/Control: 31SFB - Process

Emission Source/Control: 31STH - Process

Emission Source/Control: 31WSB - Process

Emission Source/Control: DRSTK - Process

Item 477.155(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 189

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #189 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF.

Emission Source/Control: 78FCB - Control

Control Type: FABRIC FILTER

Emission Source/Control: 78BUH - Process

Emission Source/Control: 78DME - Process

Emission Source/Control: 78FDM - Process

Emission Source/Control: 78FEH - Process

Emission Source/Control: 78FSC - Process

Item 477.156(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:



Emission Unit: C-27018

Process: 201

Source Classification Code: 3-85-001-10

Process Description:

Heat exchange system. This process represents cooling water from heat exchange systems within the miscellaneous organic chemical manufacturing units (MCPUs) with C-27018 that are regulated under 40 CFR Part 63, Subpart FFFF (Miscellaneous Organic Chemical Manufacturing).

Emission Source/Control: HXC18 - Process

Item 477.157(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 202

Source Classification Code: 3-85-001-10

Process Description:

Heat exchange system. This process represents cooling water from heat exchange systems within the miscellaneous organic chemical manufacturing units (MCPUs) within C-27035 that are regulated under 40 CFR Part 63, Subpart FFFF (Miscellaneous Organic Chemical Manufacturing).

Emission Source/Control: HXC35 - Process

Item 477.158(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 205

Source Classification Code: 3-01-999-99

Process Description:

This process represents the management of Group 1 residues in containers. The Group 1 residues are generated by the miscellaneous organic chemical manufacturing units (MCPUs) in C-27035 that are regulated under 40 CFR Part 63, Subpart FFFF (Miscellaneous Organic Chemical Manufacturing).

Emission Source/Control: RES35 - Process

Item 477.159(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 206

Source Classification Code: 3-01-026-30

Process Description:

A batch polymer kettle, PK-9 with condenser receiver vents when the kettle is filled (during charging and chemical additions) and when purging (during drying.) (4)
Vacuum stripping with N2 purge

Emission Source/Control: 78PK9 - Process



Emission Source/Control: 78PKV - Process

Item 477.160(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 217

Source Classification Code: 3-05-102-99

Process Description:

1 - the bulk product storage tanks acetoxy catalyst metering tanks and acetoxy feed hoppers vent

02 - bulk product storage tanks and packaging machine feed hoppers which contain sealant-x product

04 - a caulker filling machine uses a small pressure vessel to fill caulkers with sealant.

Emission Source/Control: 00582 - Control

Control Type: VENTURI SCRUBBER

Emission Source/Control: 0057F - Process

Emission Source/Control: 00580 - Process

Emission Source/Control: 00581 - Process

Item 477.161(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 402

Source Classification Code: 3-01-070-02

Process Description:

Methanol storage tanks. Two storage tanks that supply Methanol to the Methyl Chloride reactors in building 34. Both tanks are equipped with an internal floating roof.

Emission Source/Control: 27FRA - Control

Control Type: FLOATING ROOF

Emission Source/Control: 27FRB - Control

Control Type: FLOATING ROOF

Emission Source/Control: 27STA - Process

Emission Source/Control: 27STB - Process

Item 477.162(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 403

Source Classification Code: 3-01-820-10

Process Description:

Process wastewater. This process represents process



wastewater from the Methyl Chloride chemical manufacturing process unit.

Emission Source/Control: PROWW - Process

Item 477.163(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 404

Source Classification Code: 3-01-820-10

Process Description:

Maintenance wastewater. This process represents maintenance wastewater from the Methyl Chloride chemical manufacturing process unit.

Emission Source/Control: MNTWW - Process

Item 477.164(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 420

Source Classification Code: 3-01-026-30

Process Description:

LDH/Siloxane oil production. Insignificant emissions from the Cracker preheaters drain tank which receives water and Cyclic Siloxanes from preheaters on Crackers B C and D.

Emission Source/Control: 35CPH - Process

Item 477.165(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 700

Source Classification Code: 3-01-070-02

Process Description:

Tank farm. Insignificant emissions from 30,000 gallon storage tank 539. Tank has a continuous Nitrogen purge.

Emission Source/Control: 62EST - Control

Control Type: SPRAY TOWER

Emission Source/Control: 62EVS - Control

Control Type: VENTURI SCRUBBER

Emission Source/Control: 62WST - Control

Control Type: SPRAY TOWER

Emission Source/Control: 62WVS - Control

Control Type: VENTURI SCRUBBER

Emission Source/Control: MCSS1 - Control

Control Type: VENTURI SCRUBBER



Emission Source/Control: 62RP2 - Process

Emission Source/Control: 62RP3 - Process

Emission Source/Control: 62SC2 - Process

Emission Source/Control: 62SC3 - Process

Emission Source/Control: 62SC4 - Process

Emission Source/Control: 62SP4 - Process

Item 477.166(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 701

Source Classification Code: 3-99-999-94

Process Description:

Low boiling distillation and redistribution. This process consists of multiple distillation columns and two reactors in the low boiling distillation and redistribution area which vent to the waste incinerators or the MCS vent scrubber.

Emission Source/Control: 62EST - Control

Control Type: SPRAY TOWER

Emission Source/Control: 62EVS - Control

Control Type: VENTURI SCRUBBER

Emission Source/Control: 62WST - Control

Control Type: SPRAY TOWER

Emission Source/Control: 62WVS - Control

Control Type: VENTURI SCRUBBER

Emission Source/Control: FBCS1 - Control

Control Type: PACKED-GAS ABSORPTION SYSTEM

Emission Source/Control: FBCS2 - Control

Control Type: PACKED-GAS ABSORPTION SYSTEM

Emission Source/Control: FBIAB - Control

Control Type: DIRECT FLAME AFTERBURNER

Emission Source/Control: FBIQU - Control

Control Type: SPRAY TOWER

Emission Source/Control: IWS11 - Control

Control Type: WET SCRUBBER

Emission Source/Control: IWS12 - Control



Control Type: WET SCRUBBER

Emission Source/Control: IWS1A - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS1B - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS1C - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS21 - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS22 - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS2A - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS2B - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS2C - Control
Control Type: WET SCRUBBER

Emission Source/Control: RKIAB - Control
Control Type: DIRECT FLAME AFTERBURNER

Emission Source/Control: RKICS - Control
Control Type: PACKED-GAS ABSORPTION SYSTEM

Emission Source/Control: RKIQU - Control
Control Type: SPRAY TOWER

Emission Source/Control: 101CO - Process

Emission Source/Control: 110CO - Process

Emission Source/Control: 112AB - Process

Emission Source/Control: 113CC - Process

Emission Source/Control: 62RRE - Process

Emission Source/Control: 97NRR - Process

Item 477.167(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 702

Source Classification Code: 3-99-999-94

Process Description:



MCS IV reactor purge. This process consists of a purge on a reactor vessel.

Emission Source/Control: 62EST - Control
Control Type: SPRAY TOWER

Emission Source/Control: 62EVS - Control
Control Type: VENTURI SCRUBBER

Emission Source/Control: 62WST - Control
Control Type: SPRAY TOWER

Emission Source/Control: 62WVS - Control
Control Type: VENTURI SCRUBBER

Emission Source/Control: 62RP4 - Process

Item 477.168(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018
Process: 704 Source Classification Code: 3-01-840-01
Process Description:
Methanol recovery columns. Dual distillation columns which recover Methanol from water scrubber bottom product.

Emission Source/Control: 34RCA - Process

Emission Source/Control: 34RCB - Process

Item 477.169(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018
Process: 705 Source Classification Code: 3-99-999-94
Process Description:
This process consists of slurry and Silane tanks which vent when filled (working losses) to the waste incinerators as an alternate and equivalent means of control.

Emission Source/Control: FBCS1 - Control
Control Type: PACKED-GAS ABSORPTION SYSTEM

Emission Source/Control: FBCS2 - Control
Control Type: PACKED-GAS ABSORPTION SYSTEM

Emission Source/Control: FBIAB - Control
Control Type: DIRECT FLAME AFTERBURNER

Emission Source/Control: FBIQU - Control
Control Type: SPRAY TOWER



Emission Source/Control: IWS11 - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS12 - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS1A - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS1B - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS1C - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS21 - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS22 - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS2A - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS2B - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS2C - Control
Control Type: WET SCRUBBER

Emission Source/Control: RKIAB - Control
Control Type: DIRECT FLAME AFTERBURNER

Emission Source/Control: RKICS - Control
Control Type: PACKED-GAS ABSORPTION SYSTEM

Emission Source/Control: RKIQU - Control
Control Type: SPRAY TOWER

Emission Source/Control: 97HT1 - Process

Emission Source/Control: 97HT2 - Process

Emission Source/Control: SSTVT - Process

Item 477.170(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 706

Source Classification Code: 3-01-070-02

Process Description:

HCl compressor and GDH start up. This process represents



Control Type: PACKED-GAS ABSORPTION SYSTEM

Emission Source/Control: FBIAB - Control
Control Type: DIRECT FLAME AFTERBURNER

Emission Source/Control: FBIQU - Control
Control Type: SPRAY TOWER

Emission Source/Control: IWS11 - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS12 - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS1A - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS1B - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS1C - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS21 - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS22 - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS2A - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS2B - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS2C - Control
Control Type: WET SCRUBBER

Emission Source/Control: RKIAB - Control
Control Type: DIRECT FLAME AFTERBURNER

Emission Source/Control: RKICS - Control
Control Type: PACKED-GAS ABSORPTION SYSTEM

Emission Source/Control: RKIQU - Control
Control Type: SPRAY TOWER

Emission Source/Control: 114BC - Process

Item 477.173(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018



Process: 715 Source Classification Code: 3-01-018-47

Process Description:

MQ Resins. Resins and polymers are held for further processing in a closed, stirred process kettle.

Emission Source/Control: 24WSH - Process

Emission Source/Control: 30SLT - Process

Item 477.174(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 719

Source Classification Code: 3-01-026-30

Process Description:

East and West Hydrolyzers. The East and West Hydrolyzers vent to the East and West High Acid Scrubbers.

Emission Source/Control: 76EHY - Process

Emission Source/Control: 76WHY - Process

Item 477.175(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 723

Source Classification Code: 3-99-999-94

Process Description:

Batch Mixing The 225 gallon Day Mixer, the 500 Day Mixer, and the 500 gallon B-K Mixer vent through a common vacuum pump. The mixers are used to mix silicone.

Emission Source/Control: 302GD - Process

Emission Source/Control: 305GD - Process

Emission Source/Control: 30BKM - Process

Item 477.176(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 726

Source Classification Code: 3-01-070-02

Process Description:

East System - This process consists of the East System Filter Press.

Emission Source/Control: 24EBK - Process

Emission Source/Control: 24EHY - Process

Emission Source/Control: 24EST - Process



Item 477.177(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 727

Source Classification Code: 3-01-026-30

Process Description:

West System - manufactures products such as auto polishes, masonry water repellent, impregnant for roofing granules, and process aids for rubber production. It is a batch system that is a hydrolysis system. Associated equipment includes a filter press.

Emission Source/Control: 76FP2 - Process

Item 477.178(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 730

Source Classification Code: 3-01-026-30

Process Description:

East resins. Under atmospheric conditions, emissions from a body kettle condenser vent. Emissions from the kettle can also go to a receiver vent.

Emission Source/Control: 24BR2 - Process

Item 477.179(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 731

Source Classification Code: 3-01-026-30

Process Description:

Transfer truck unloading. Tank wagon loading/unloading station.

Emission Source/Control: 24BOD - Process

Emission Source/Control: 24BR1 - Process

Item 477.180(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 732

Source Classification Code: 3-99-999-94

Process Description:

1M reactor. Local ventilation system used to remove Dimethylformamide vapors during filter rebuild.

Emission Source/Control: 71RT1 - Process

Emission Source/Control: 71RT2 - Process

Item 477.181(From Mod 0):



This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018
Process: 733 Source Classification Code: 3-01-070-02
Process Description:
4000 PUFA. Methyl Styrene storage tank working losses.

Emission Source/Control: 37MST - Process
Design Capacity: 10,000 gallons

Item 477.182(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018
Process: 737 Source Classification Code: 3-01-840-01
Process Description:
Chlorosilane distillation. This process consists of
distillation columns in the Chlorosilane distillation area
which vent to the MCS vent scrubber.

Emission Source/Control: 62EST - Control
Control Type: SPRAY TOWER

Emission Source/Control: 62EVS - Control
Control Type: VENTURI SCRUBBER

Emission Source/Control: 62WST - Control
Control Type: SPRAY TOWER

Emission Source/Control: 62WVS - Control
Control Type: VENTURI SCRUBBER

Emission Source/Control: 113AB - Process

Emission Source/Control: 114AC - Process

Emission Source/Control: 116AB - Process

Emission Source/Control: 119CO - Process

Item 477.183(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018
Process: 741 Source Classification Code: 3-01-026-30
Process Description:
3M hydrolyzer. A 3000 gallon multifunctional batch system
used to manufacture various product grades. The hydrolyzer
is used for hydrolysis reactions, cold mixes, and
equilibrium processes. Associated equipment includes weigh
tanks, drum/tanker charging, filters.

Emission Source/Control: 71HYS - Control



Control Type: WET SCRUBBER

Emission Source/Control: 71CR1 - Process

Emission Source/Control: 71CR2 - Process

Emission Source/Control: 71CR5 - Process

Emission Source/Control: 71CR7 - Process

Emission Source/Control: 71CR8 - Process

Emission Source/Control: 71DS3 - Process

Emission Source/Control: 71FP1 - Process

Emission Source/Control: 71FP3 - Process

Emission Source/Control: 71HY3 - Process

Emission Source/Control: 71RT1 - Process

Emission Source/Control: 71SIL - Process

Emission Source/Control: 71SWT - Process

Emission Source/Control: 71WT7 - Process

Item 477.184(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 746

Source Classification Code: 3-99-999-94

Process Description:

Storage tanks - working losses. This process consists of working losses from storage tanks which vent to the MCS vent scrubber or the waste incinerators.

Emission Source/Control: 62EST - Control

Control Type: SPRAY TOWER

Emission Source/Control: 62EVS - Control

Control Type: VENTURI SCRUBBER

Emission Source/Control: 62WST - Control

Control Type: SPRAY TOWER

Emission Source/Control: 62WVS - Control

Control Type: VENTURI SCRUBBER

Emission Source/Control: FBCS2 - Control

Control Type: PACKED-GAS ABSORPTION SYSTEM



Emission Source/Control: FBIAB - Control
Control Type: DIRECT FLAME AFTERBURNER

Emission Source/Control: FBIQU - Control
Control Type: SPRAY TOWER

Emission Source/Control: IWS11 - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS12 - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS1A - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS1B - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS21 - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS22 - Control
Control Type: WET SCRUBBER

Emission Source/Control: RKIAB - Control
Control Type: DIRECT FLAME AFTERBURNER

Emission Source/Control: RKICS - Control
Control Type: PACKED-GAS ABSORPTION SYSTEM

Emission Source/Control: RKIQU - Control
Control Type: SPRAY TOWER

Emission Source/Control: 024TK - Process

Emission Source/Control: 521TK - Process

Emission Source/Control: 522TK - Process

Emission Source/Control: 564AT - Process

Emission Source/Control: 599BT - Process

Emission Source/Control: 625AB - Process

Emission Source/Control: 625CS - Process

Emission Source/Control: 62BRT - Process

Emission Source/Control: 62CST - Process

Emission Source/Control: 62CTA - Process



Emission Source/Control: 62CTB - Process

Emission Source/Control: 62T5C - Process

Emission Source/Control: 62T5E - Process

Emission Source/Control: 62TST - Process

Emission Source/Control: 66TFA - Process

Emission Source/Control: TK562 - Process

Emission Source/Control: TRIST - Process

Item 477.185(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 748

Source Classification Code: 3-99-999-94

Process Description:

TCS/FS to incinerators or scrubbers. This process consists of sources in the Tri-Chlorosilane and fumed Silica operating areas which vent to the waste incinerators or the MCS vent scrubbers.

Emission Source/Control: 62EST - Control

Control Type: SPRAY TOWER

Emission Source/Control: 62EVS - Control

Control Type: VENTURI SCRUBBER

Emission Source/Control: 62WST - Control

Control Type: SPRAY TOWER

Emission Source/Control: 62WVS - Control

Control Type: VENTURI SCRUBBER

Emission Source/Control: FBCS1 - Control

Control Type: PACKED-GAS ABSORPTION SYSTEM

Emission Source/Control: FBCS2 - Control

Control Type: PACKED-GAS ABSORPTION SYSTEM

Emission Source/Control: FBIAB - Control

Control Type: DIRECT FLAME AFTERBURNER

Emission Source/Control: FBIQU - Control

Control Type: SPRAY TOWER

Emission Source/Control: IWS11 - Control

Control Type: WET SCRUBBER

Emission Source/Control: IWS12 - Control



Control Type: WET SCRUBBER

Emission Source/Control: IWS1A - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS1B - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS21 - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS22 - Control
Control Type: WET SCRUBBER

Emission Source/Control: RKIAB - Control
Control Type: DIRECT FLAME AFTERBURNER

Emission Source/Control: RKICS - Control
Control Type: PACKED-GAS ABSORPTION SYSTEM

Emission Source/Control: RKIQU - Control
Control Type: SPRAY TOWER

Emission Source/Control: 62RFC - Process

Emission Source/Control: FSSRV - Process

Emission Source/Control: RCACO - Process

Emission Source/Control: TCSR - Process

Emission Source/Control: TCSRT - Process

Item 477.186(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-27018

Process: 749

Source Classification Code: 5-03-007-01

Process Description:

Waste treatment incinerators. This process consists of the Rotary Kiln Incinerator and the Fixed Box Incinerator no. 2 in the waste treatment plant.

Emission Source/Control: FBCS1 - Control
Control Type: PACKED-GAS ABSORPTION SYSTEM

Emission Source/Control: FBCS2 - Control
Control Type: PACKED-GAS ABSORPTION SYSTEM

Emission Source/Control: FBIAB - Control
Control Type: DIRECT FLAME AFTERBURNER

Emission Source/Control: FBIQU - Control



Control Type: SPRAY TOWER

Emission Source/Control: IWS11 - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS12 - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS1A - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS1B - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS1C - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS21 - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS22 - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS2A - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS2B - Control
Control Type: WET SCRUBBER

Emission Source/Control: IWS2C - Control
Control Type: WET SCRUBBER

Emission Source/Control: RKIAB - Control
Control Type: DIRECT FLAME AFTERBURNER

Emission Source/Control: RKICS - Control
Control Type: PACKED-GAS ABSORPTION SYSTEM

Emission Source/Control: RKIQU - Control
Control Type: SPRAY TOWER

Emission Source/Control: 936FB - Incinerator
Design Capacity: 27.1 million Btu per hour
Waste Feed Method: MANUAL DIRECT FEED
Waste Type: HAZARDOUS WASTE

Emission Source/Control: 96RKI - Incinerator
Design Capacity: 30 million Btu per hour
Waste Feed Method: MANUAL DIRECT FEED
Waste Type: HAZARDOUS WASTE

Item 477.187(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:



Emission Unit: C-27018

Process: FIN

Source Classification Code: 3-01-999-99

Process Description:

This process represents the chemical manufacturing process sources that have been re-organized from the finishing emission unit (F-INISH) to C-27018 due to changes needed for compliance with MON requirements.

Emission Source/Control: 23BSS - Control

Control Type: WET SCRUBBER

Emission Source/Control: 24ADC - Control

Control Type: FABRIC FILTER

Emission Source/Control: 24ARS - Control

Control Type: VAPOR RECOVERY SYS(INCL.
CONDENSERS,HOODING, OTHER ENCLOSURES)

Emission Source/Control: 24AVR - Control

Control Type: VAPOR RECOVERY SYS(INCL.
CONDENSERS,HOODING, OTHER ENCLOSURES)

Emission Source/Control: 24GBF - Control

Control Type: GRAVEL BED FILTER

Emission Source/Control: 24PGA - Control

Control Type: PACKED-GAS ABSORPTION SYSTEM

Emission Source/Control: 31DB1 - Control

Control Type: FABRIC FILTER

Emission Source/Control: 31DB2 - Control

Control Type: FABRIC FILTER

Emission Source/Control: 31DC1 - Control

Control Type: REFRIGERATED CONDENSER

Emission Source/Control: 31DC2 - Control

Control Type: REFRIGERATED CONDENSER

Emission Source/Control: 31DMS - Control

Control Type: WET SCRUBBER

Emission Source/Control: 31FS1 - Control

Control Type: WET SCRUBBER

Emission Source/Control: 37BDC - Control

Control Type: FABRIC FILTER

Emission Source/Control: 71HYS - Control

Control Type: WET SCRUBBER



Emission Source/Control: 76EAS - Control
Control Type: GAS SCRUBBER (GENERAL, NOT CLASSIFIED)

Emission Source/Control: 76ESC - Control
Control Type: FABRIC FILTER

Emission Source/Control: 76EWS - Control
Control Type: VENTURI SCRUBBER

Emission Source/Control: 76HTV - Control
Control Type: CONSERVATION VENT

Emission Source/Control: 76WAS - Control
Control Type: GAS SCRUBBER (GENERAL, NOT CLASSIFIED)

Emission Source/Control: 76WSC - Control
Control Type: FABRIC FILTER

Emission Source/Control: 78FCB - Control
Control Type: FABRIC FILTER

Emission Source/Control: 23TNS - Process

Emission Source/Control: 23TST - Process

Emission Source/Control: 24AID - Process

Emission Source/Control: 24ANE - Process

Emission Source/Control: 24ART - Process

Emission Source/Control: 24ATK - Process

Emission Source/Control: 24BD1 - Process

Emission Source/Control: 24BD2 - Process

Emission Source/Control: 24BKC - Process

Emission Source/Control: 24BKR - Process

Emission Source/Control: 24BLK - Process

Emission Source/Control: 24BR2 - Process

Emission Source/Control: 24CHI - Process

Emission Source/Control: 24CHT - Process

Emission Source/Control: 24DRE - Process

Emission Source/Control: 24ENZ - Process



Emission Source/Control: 24FAH - Process
Emission Source/Control: 24FAK - Process
Emission Source/Control: 24FK4 - Process
Emission Source/Control: 24FOK - Process
Emission Source/Control: 24FTO - Process
Emission Source/Control: 24HCO - Process
Emission Source/Control: 24HT1 - Process
Emission Source/Control: 24HT2 - Process
Emission Source/Control: 24HYD - Process
Emission Source/Control: 24MHC - Process
Emission Source/Control: 24N12 - Process
Emission Source/Control: 24NO1 - Process
Emission Source/Control: 24NO5 - Process
Emission Source/Control: 24PBT - Process
Emission Source/Control: 24PCT - Process
Emission Source/Control: 24PRE - Process
Emission Source/Control: 24PRT - Process
Emission Source/Control: 24PSR - Process
Emission Source/Control: 24PSS - Process
Emission Source/Control: 24RST - Process
Emission Source/Control: 24SF1 - Process
Emission Source/Control: 24SF2 - Process
Emission Source/Control: 24SGS - Process
Emission Source/Control: 24SHT - Process
Emission Source/Control: 24SIL - Process
Emission Source/Control: 24SOU - Process
Emission Source/Control: 24SOX - Process



Emission Source/Control: 24SRA - Process

Emission Source/Control: 24SST - Process

Emission Source/Control: 24T12 - Process

Emission Source/Control: 24WSH - Process

Emission Source/Control: 24WST - Process

Emission Source/Control: 24WTA - Process

Emission Source/Control: 302GD - Process

Emission Source/Control: 305GD - Process

Emission Source/Control: 30BKM - Process

Emission Source/Control: 30LET - Process

Emission Source/Control: 30MTA - Process

Emission Source/Control: 30MTB - Process

Emission Source/Control: 30PT1 - Process

Emission Source/Control: 30PT2 - Process

Emission Source/Control: 30SLT - Process

Emission Source/Control: 31630 - Process

Emission Source/Control: 31APL - Process

Emission Source/Control: 31AS6 - Process

Emission Source/Control: 31CPD - Process

Emission Source/Control: 31ESB - Process

Emission Source/Control: 31FKR - Process

Emission Source/Control: 31FP1 - Process

Emission Source/Control: 31FP2 - Process

Emission Source/Control: 31FP3 - Process

Emission Source/Control: 31FS2 - Process

Emission Source/Control: 31GHV - Process



Emission Source/Control: 31LKR - Process

Emission Source/Control: 31LNM - Process

Emission Source/Control: 31LSM - Process

Emission Source/Control: 31LTS - Process

Emission Source/Control: 31NAS - Process

Emission Source/Control: 31NBH - Process

Emission Source/Control: 31PDR - Process

Emission Source/Control: 31RSR - Process

Emission Source/Control: 31SAS - Process

Emission Source/Control: 31SFB - Process

Emission Source/Control: 31STH - Process

Emission Source/Control: 31WPD - Process

Emission Source/Control: 31WSB - Process

Emission Source/Control: 32DMX - Process

Emission Source/Control: 32WTD - Process

Emission Source/Control: 36ST4 - Process

Emission Source/Control: 372MK - Process

Emission Source/Control: 373MF - Process

Emission Source/Control: 374MD - Process

Emission Source/Control: 374MK - Process

Emission Source/Control: 374MP - Process

Emission Source/Control: 374ST - Process

Emission Source/Control: 37750 - Process

Emission Source/Control: 37ART - Process

Emission Source/Control: 37ASB - Process

Emission Source/Control: 37BDD - Process

Emission Source/Control: 37CE1 - Process



Emission Source/Control: 37CST - Process

Emission Source/Control: 37D4F - Process

Emission Source/Control: 37EJE - Process

Emission Source/Control: 37EJV - Process

Emission Source/Control: 37FAK - Process

Emission Source/Control: 37FAT - Process

Emission Source/Control: 37FBP - Process

Emission Source/Control: 37FCS - Process

Emission Source/Control: 37FEF - Process

Emission Source/Control: 37GPR - Process

Emission Source/Control: 37GV1 - Process

Emission Source/Control: 37GW7 - Process

Emission Source/Control: 37GWT - Process

Emission Source/Control: 37NTL - Process

Emission Source/Control: 37PRE - Process

Emission Source/Control: 37PRV - Process

Emission Source/Control: 37RHE - Process

Emission Source/Control: 37RHH - Process

Emission Source/Control: 37SSR - Process

Emission Source/Control: 37ST2 - Process

Emission Source/Control: 37ST3 - Process

Emission Source/Control: 37ST7 - Process

Emission Source/Control: 37ST8 - Process

Emission Source/Control: 37ST9 - Process

Emission Source/Control: 37T18 - Process

Emission Source/Control: 37TA2 - Process



Emission Source/Control: 37TA3 - Process

Emission Source/Control: 37TAN - Process

Emission Source/Control: 37VAC - Process

Emission Source/Control: 37VSS - Process

Emission Source/Control: 71CR1 - Process

Emission Source/Control: 71CR2 - Process

Emission Source/Control: 71CR5 - Process

Emission Source/Control: 71CR7 - Process

Emission Source/Control: 71CR8 - Process

Emission Source/Control: 71DS3 - Process

Emission Source/Control: 71FP1 - Process

Emission Source/Control: 71FP3 - Process

Emission Source/Control: 71HES - Process

Emission Source/Control: 71HY3 - Process

Emission Source/Control: 71HZR - Process

Emission Source/Control: 71RT1 - Process

Emission Source/Control: 71RT2 - Process

Emission Source/Control: 71SIL - Process

Emission Source/Control: 71SWT - Process

Emission Source/Control: 71VAC - Process

Emission Source/Control: 71WT7 - Process

Emission Source/Control: 76ACT - Process

Emission Source/Control: 76ACW - Process

Emission Source/Control: 76APS - Process

Emission Source/Control: 76BUT - Process

Emission Source/Control: 76CH1 - Process

Emission Source/Control: 76CH2 - Process



Emission Source/Control: 76DV1 - Process

Emission Source/Control: 76DV2 - Process

Emission Source/Control: 76DV3 - Process

Emission Source/Control: 76EFK - Process

Emission Source/Control: 76EHC - Process

Emission Source/Control: 76EHW - Process

Emission Source/Control: 76EHY - Process

Emission Source/Control: 76EPT - Process

Emission Source/Control: 76ERC - Process

Emission Source/Control: 76ESB - Process

Emission Source/Control: 76FP1 - Process

Emission Source/Control: 76FP2 - Process

Emission Source/Control: 76HST - Process

Emission Source/Control: 76HT6 - Process

Emission Source/Control: 76HTS - Process

Emission Source/Control: 76MST - Process

Emission Source/Control: 76PBT - Process

Emission Source/Control: 76SBS - Process

Emission Source/Control: 76STS - Process

Emission Source/Control: 76STW - Process

Emission Source/Control: 76TL1 - Process

Emission Source/Control: 76TL2 - Process

Emission Source/Control: 76TL3 - Process

Emission Source/Control: 76TUS - Process

Emission Source/Control: 76TWL - Process

Emission Source/Control: 76WFK - Process



- Emission Source/Control: 76WHC - Process
- Emission Source/Control: 76WHR - Process
- Emission Source/Control: 76WHW - Process
- Emission Source/Control: 76WHY - Process
- Emission Source/Control: 76WPT - Process
- Emission Source/Control: 76WSB - Process
- Emission Source/Control: 76WSW - Process
- Emission Source/Control: 78BUH - Process
- Emission Source/Control: 78DME - Process
- Emission Source/Control: 78FDM - Process
- Emission Source/Control: 78FEH - Process
- Emission Source/Control: 78FSC - Process
- Emission Source/Control: 78HWV - Process
- Emission Source/Control: 78MVS - Process
- Emission Source/Control: 78P14 - Process
- Emission Source/Control: 78PK1 - Process
- Emission Source/Control: 78PK2 - Process
- Emission Source/Control: 78PK9 - Process
- Emission Source/Control: 78PKV - Process
- Emission Source/Control: 78RVC - Process
- Emission Source/Control: 78VES - Process
- Emission Source/Control: PESV1 - Process
- Emission Source/Control: PESV2 - Process
- Emission Source/Control: PESV3 - Process
- Emission Source/Control: PESV4 - Process
- Emission Source/Control: PESV5 - Process
- Emission Source/Control: PESV6 - Process



Emission Source/Control: PESV7 - Process
Emission Source/Control: PESV8 - Process
Emission Source/Control: PJORS - Process
Emission Source/Control: PKSDT - Process
Emission Source/Control: POLY1 - Process
Emission Source/Control: POLY2 - Process
Emission Source/Control: POLY3 - Process
Emission Source/Control: POLY4 - Process
Emission Source/Control: POLY5 - Process
Emission Source/Control: POLY6 - Process
Emission Source/Control: POLY7 - Process
Emission Source/Control: POLY8 - Process
Emission Source/Control: RH502 - Process
Emission Source/Control: RHFTK - Process
Emission Source/Control: RHJOD - Process
Emission Source/Control: RHPTK - Process

Item 477.188(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-61007

Process: 711

Source Classification Code: 3-99-999-94

Process Description:

Old Silicon grinding plant - unloads Silicon metal from rail cars to buffer silo. Silicon is fed from buffer silo to ball mill. Ball mill grinds Silicon and discharges ground powder to screener. Finished product is placed in silos; oversize material is recycled from screener to mill.

Emission Source/Control: 61SGB - Control

Control Type: FABRIC FILTER

Emission Source/Control: SGDC1 - Process

Emission Source/Control: SGDC2 - Process



Emission Source/Control: SGDC3 - Process

Emission Source/Control: SGDC4 - Process

Emission Source/Control: SGHVC - Process

Item 477.189(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-61007

Process: GCC

Source Classification Code: 3-99-999-94

Process Description:

Fines passivation. Fines are mixed with Lignin and water to neutralize and harden the material. Associated equipment is a bag dump station.

Emission Source/Control: GC5C1 - Control

Control Type: FABRIC FILTER

Emission Source/Control: GC501 - Process

Item 477.190(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-62008

Process: 419

Source Classification Code: 1-02-005-03

Process Description: MCS Hot oil furnaces with limits on #2 fuel oil.

Emission Source/Control: 55HOF - Combustion

Emission Source/Control: 57HOF - Combustion

Emission Source/Control: 65HOF - Combustion

Item 477.191(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-62008

Process: MCW

Source Classification Code: 3-01-070-02

Process Description:

MCS-Tanks - Working Loss - This process consists of Working Losses from tanks in the MCS production operation.

Emission Source/Control: GE901 - Process

Emission Source/Control: GF201 - Process

Item 477.192(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: C-62014

Process: 407

Source Classification Code: 3-01-026-30



Process Description:

Fumed Silica scrubber. This process consists of a scrubber which removes Chlorine, Hydrogen Chloride, and Particulates.

Emission Source/Control: 100CO - Process

Item 477.193(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: F-INISH

Process: 014

Source Classification Code: 3-01-999-99

Process Description:

This process represents FOM 014, which is a miscellaneous organic chemical manufacturing unit (MCPU) that is regulated under 40 CFR Part 63, Subpart FFFF (Miscellaneous Organic Chemical Manufacturing)

Emission Source/Control: 37FUM - Process

Emission Source/Control: 37GT6 - Process

Item 477.194(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: F-INISH

Process: 015

Source Classification Code: 3-01-999-99

Process Description:

This process represents FOM 015, which is a miscellaneous organic chemical manufacturing unit (MCPU) that is regulated under 40 CFR Part 63, Subpart FFFF (Miscellaneous Organic Chemical Manufacturing)

Emission Source/Control: 37FUM - Process

Emission Source/Control: 37GT6 - Process

Emission Source/Control: 41TR1 - Process

Item 477.195(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: F-INISH

Process: 016

Source Classification Code: 3-01-999-99

Process Description:

This process represents FOM 016, which is a miscellaneous organic chemical manufacturing unit (MCPU) that is regulated under 40 CFR Part 63, Subpart FFFF (Miscellaneous Organic Chemical Manufacturing)

Emission Source/Control: 37FUM - Process

Emission Source/Control: 37GT6 - Process



Item 477.196(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: F-INISH

Process: 017

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #017, which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63, SubPart FFFF.

Emission Source/Control: 37FUM - Process

Emission Source/Control: 37GT6 - Process

Item 477.197(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: F-INISH

Process: 018

Source Classification Code: 3-01-999-99

Process Description:

This process represents FOM 018, which is a miscellaneous organic chemical manufacturing unit (MCPU) that is regulated under 40 CFR Part 63, Subpart FFFF (Miscellaneous Organic Chemical Manufacturing)

Emission Source/Control: 37FUM - Process

Emission Source/Control: 37GT2 - Process

Emission Source/Control: 37GT6 - Process

Item 477.198(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: F-INISH

Process: 019

Source Classification Code: 3-01-999-99

Process Description:

This process represents FOM 019, which is a miscellaneous organic chemical manufacturing unit (MCPU) that is regulated under 40 CFR Part 63, Subpart FFFF (Miscellaneous Organic Chemical Manufacturing)

Emission Source/Control: 37FUM - Process

Emission Source/Control: 37GT2 - Process

Emission Source/Control: 37GT6 - Process

Item 477.199(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: F-INISH



Process: 020 Source Classification Code: 3-01-999-99

Process Description:

This process represents FOM 020, which is a miscellaneous organic chemical manufacturing unit (MCPU) that is regulated under 40 CFR Part 63, Subpart FFFF (Miscellaneous Organic Chemical Manufacturing)

Emission Source/Control: 37FUM - Process

Emission Source/Control: 37GT2 - Process

Emission Source/Control: 37GT6 - Process

Item 477.200(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: F-INISH

Process: 029

Source Classification Code: 3-01-999-99

Process Description:

This process represents FOM 029, which is a miscellaneous organic chemical manufacturing unit (MCPU) that is regulated under 40 CFR Part 63, Subpart FFFF (Miscellaneous Organic Chemical Manufacturing)

Emission Source/Control: 85DRS - Process

Emission Source/Control: 85DUH - Process

Emission Source/Control: 85GC5 - Process

Item 477.201(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: F-INISH

Process: 057

Source Classification Code: 3-01-999-99

Process Description:

This process represents FOM 057, which is a miscellaneous organic chemical manufacturing unit (MCPU) that is regulated under 40 CFR Part 63, Subpart FFFF (Miscellaneous Organic Chemical Manufacturing)

Emission Source/Control: 42DS1 - Process

Emission Source/Control: 42DS2 - Process

Emission Source/Control: 42PRH - Process

Emission Source/Control: 42RM1 - Process

Emission Source/Control: 42RM2 - Process

Emission Source/Control: 42RM3 - Process



Item 477.202(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: F-INISH

Process: 058

Source Classification Code: 3-01-999-99

Process Description:

This process represents FOM 058, which is a miscellaneous organic chemical manufacturing unit (MCPU) that is regulated under 40 CFR Part 63, Subpart FFFF (Miscellaneous Organic Chemical Manufacturing)

Emission Source/Control: 42DS1 - Process

Emission Source/Control: 42DS2 - Process

Emission Source/Control: 42PRH - Process

Emission Source/Control: 42RM1 - Process

Emission Source/Control: 42RM2 - Process

Emission Source/Control: 42RM3 - Process

Item 477.203(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: F-INISH

Process: 059

Source Classification Code: 3-01-999-99

Process Description:

This process represents FOM 059, which is a miscellaneous organic chemical manufacturing unit (MCPU) that is regulated under 40 CFR Part 63, Subpart FFFF (Miscellaneous Organic Chemical Manufacturing)

Emission Source/Control: 42DS1 - Process

Emission Source/Control: 42DS2 - Process

Emission Source/Control: 42PRH - Process

Emission Source/Control: 42RM1 - Process

Emission Source/Control: 42RM2 - Process

Emission Source/Control: 42RM3 - Process

Item 477.204(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: F-INISH

Process: 060

Source Classification Code: 3-01-999-99

Process Description:

This process represents FOM 060, which is a miscellaneous



organic chemical manufacturing unit (MCPU) that is regulated under 40 CFR Part 63, Subpart FFFF (Miscellaneous Organic Chemical Manufacturing) Building 30/42

Emission Source/Control: 42BAN - Control
Control Type: FABRIC FILTER

Emission Source/Control: 33BFV - Process

Emission Source/Control: 33BM1 - Process

Emission Source/Control: 33BM2 - Process

Emission Source/Control: 33BM3 - Process

Emission Source/Control: 33BM4 - Process

Emission Source/Control: 33CYC - Process

Emission Source/Control: 33GVS - Process

Emission Source/Control: 33HVS - Process

Emission Source/Control: 33NEU - Process

Emission Source/Control: 33POT - Process

Emission Source/Control: 33RUN - Process

Emission Source/Control: 42DS1 - Process

Emission Source/Control: 42DS2 - Process

Emission Source/Control: 42PRH - Process

Emission Source/Control: 42RM1 - Process

Emission Source/Control: 42RM2 - Process

Emission Source/Control: 42RM3 - Process

Item 477.205(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: F-INISH

Process: 063

Source Classification Code: 3-01-999-99

Process Description:

This process represents FOM 063, which is a miscellaneous organic chemical manufacturing unit (MCPU) that is regulated under 40 CFR Part 63, Subpart FFFF (Miscellaneous Organic Chemical Manufacturing) Buildings 30/42



Emission Source/Control: 42BAN - Control
Control Type: FABRIC FILTER

Emission Source/Control: 33BFV - Process

Emission Source/Control: 33BM1 - Process

Emission Source/Control: 33BM2 - Process

Emission Source/Control: 33BM3 - Process

Emission Source/Control: 33BM4 - Process

Emission Source/Control: 33CYC - Process

Emission Source/Control: 33GVS - Process

Emission Source/Control: 33HVS - Process

Emission Source/Control: 33NEU - Process

Emission Source/Control: 33POT - Process

Emission Source/Control: 33RUN - Process

Emission Source/Control: 42DS1 - Process

Emission Source/Control: 42DS2 - Process

Emission Source/Control: 42PRH - Process

Emission Source/Control: 42RM1 - Process

Emission Source/Control: 42RM2 - Process

Emission Source/Control: 42RM3 - Process

Item 477.206(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: F-INISH

Process: 065

Source Classification Code: 3-01-999-99

Process Description:

This process represents FOM 065, which is a miscellaneous organic chemical manufacturing unit (MCPU) that is regulated under 40 CFR Part 63, Subpart FFFF (Miscellaneous Organic Chemical Manufacturing) Buildings 30/42

Emission Source/Control: 42BAN - Control

Control Type: FABRIC FILTER



Emission Source/Control: 33BFV - Process

Emission Source/Control: 33BM1 - Process

Emission Source/Control: 33BM2 - Process

Emission Source/Control: 33BM3 - Process

Emission Source/Control: 33BM4 - Process

Emission Source/Control: 33CYC - Process

Emission Source/Control: 33GVS - Process

Emission Source/Control: 33HVS - Process

Emission Source/Control: 33NEU - Process

Emission Source/Control: 33POT - Process

Emission Source/Control: 33RUN - Process

Emission Source/Control: 42DS1 - Process

Emission Source/Control: 42DS2 - Process

Emission Source/Control: 42PRH - Process

Emission Source/Control: 42RM1 - Process

Emission Source/Control: 42RM2 - Process

Emission Source/Control: 42RM3 - Process

Item 477.207(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: F-INISH

Process: 076

Source Classification Code: 3-01-999-99

Process Description:

This process represents FOM 076, which is a miscellaneous organic chemical manufacturing unit (MCPU) that is regulated under 40 CFR Part 63, Subpart FFFF (Miscellaneous Organic Chemical Manufacturing)

Emission Source/Control: MCB01 - Process

Emission Source/Control: MCB02 - Process

Item 477.208(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: F-INISH



Process: 077 Source Classification Code: 3-01-999-99

Process Description:

This process represents FOM 077, which is a miscellaneous organic chemical manufacturing unit (MCPU) that is regulated under 40 CFR Part 63, Subpart FFFF (Miscellaneous Organic Chemical Manufacturing)

Emission Source/Control: MCB01 - Process

Emission Source/Control: MCB02 - Process

Item 477.209(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: F-INISH

Process: 081 Source Classification Code: 3-01-999-99

Process Description:

This process represents FOM 081, which is a miscellaneous organic chemical manufacturing unit (MCPU) that is regulated under 40 CFR Part 63, Subpart FFFF (Miscellaneous Organic Chemical Manufacturing)

Emission Source/Control: 37PHC - Control
Control Type: TUBE AND SHELL CONDENSER

Emission Source/Control: 37PHV - Control
Control Type: VAPOR RECOVERY SYS(INCL.
CONDENSERS,HOODING, OTHER ENCLOSURES)

Emission Source/Control: 37CCD - Process

Emission Source/Control: 37CRY - Process

Emission Source/Control: 37CTH - Process

Emission Source/Control: 37DST - Process

Emission Source/Control: 37HAE - Process

Emission Source/Control: 37HPT - Process

Emission Source/Control: 37PCF - Process

Emission Source/Control: 37PHO - Process

Emission Source/Control: 37PST - Process

Emission Source/Control: 37PTC - Process

Emission Source/Control: 37PTD - Process

Emission Source/Control: 37PTH - Process



Emission Source/Control: 37SW2 - Process

Emission Source/Control: 37TDS - Process

Item 477.210(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: F-INISH

Process: 136

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of material #136 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF.

Emission Source/Control: 33SHB - Control
Control Type: FABRIC FILTER

Emission Source/Control: 33ES4 - Process

Emission Source/Control: 33F12 - Process

Emission Source/Control: 33F58 - Process

Emission Source/Control: 33FDF - Process

Emission Source/Control: 33GAP - Process

Emission Source/Control: 33HOF - Process

Emission Source/Control: 33HR1 - Process

Emission Source/Control: 33HR2 - Process

Emission Source/Control: 33LDP - Process

Emission Source/Control: 33ST1 - Process

Emission Source/Control: 33ST2 - Process

Emission Source/Control: 33ST3 - Process

Emission Source/Control: 33ST4 - Process

Emission Source/Control: 33T19 - Process

Emission Source/Control: 33T23 - Process

Emission Source/Control: 33TDS - Process

Emission Source/Control: 33WDD - Process

Emission Source/Control: 33WF1 - Process



Emission Source/Control: 33WF2 - Process

Emission Source/Control: 33WP1 - Process

Emission Source/Control: 33WP2 - Process

Emission Source/Control: 33WP3 - Process

Emission Source/Control: 33WP4 - Process

Emission Source/Control: 33WPF - Process

Emission Source/Control: 33WV1 - Process

Emission Source/Control: 33WV2 - Process

Item 477.211(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: F-INISH

Process: 155

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #155 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Oart 63 Subpart FFFF.

Emission Source/Control: 78LED - Process

Emission Source/Control: 78NFT - Process

Emission Source/Control: 78SFT - Process

Emission Source/Control: 78TFE - Process

Item 477.212(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: F-INISH

Process: 159

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #159 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Oart 63 Subpart FFFF.

Emission Source/Control: 42DS1 - Process

Emission Source/Control: 42DS2 - Process

Emission Source/Control: 42PRH - Process

Emission Source/Control: 42RM1 - Process

Emission Source/Control: 42RM2 - Process



Emission Source/Control: 42RM3 - Process

Item 477.213(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: F-INISH

Process: 165

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #165 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Oart 63 Subpart FFFF.

Emission Source/Control: 37FUM - Process

Emission Source/Control: 37GT2 - Process

Item 477.214(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: F-INISH

Process: 173

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #173 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Oart 63 Subpart FFFF.

Emission Source/Control: 78LET - Process

Emission Source/Control: 78NFT - Process

Emission Source/Control: 78SFT - Process

Emission Source/Control: 78TFE - Process

Emission Source/Control: 78TR3 - Process

Emission Source/Control: 78TR4 - Process

Item 477.215(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: F-INISH

Process: 175

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #175 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Oart 63 Subpart FFFF.

Emission Source/Control: 85CV1 - Control

Control Type: GAS SCRUBBER (GENERAL, NOT CLASSIFIED)

Emission Source/Control: 85CV2 - Control



Control Type: GAS SCRUBBER (GENERAL, NOT CLASSIFIED)

Emission Source/Control: 85CV3 - Control
Control Type: CONSERVATION VENT

Emission Source/Control: 85DCS - Control
Control Type: FABRIC FILTER

Emission Source/Control: 85TST - Control
Control Type: SPRAY TOWER

Emission Source/Control: 85BER - Process

Emission Source/Control: 85BST - Process
Design Capacity: 11,000 gallons

Emission Source/Control: 85CSC - Process

Emission Source/Control: 85CT1 - Process

Emission Source/Control: 85CT2 - Process

Emission Source/Control: 85CT3 - Process

Emission Source/Control: 85DCB - Process

Emission Source/Control: 85DRM - Process

Emission Source/Control: 85DUH - Process

Emission Source/Control: 85FPT - Process

Emission Source/Control: 85GC1 - Process

Emission Source/Control: 85GC2 - Process

Emission Source/Control: 85GC3 - Process

Emission Source/Control: 85GC4 - Process

Emission Source/Control: 85GC6 - Process

Emission Source/Control: 85GRV - Process

Emission Source/Control: 85HOP - Process

Emission Source/Control: 85HSD - Process

Emission Source/Control: 85PD0 - Process

Emission Source/Control: 85PD2 - Process

Emission Source/Control: 85PIS - Process



Emission Source/Control: 85SFH - Process

Emission Source/Control: 85ST2 - Process

Emission Source/Control: 85ST4 - Process

Emission Source/Control: 85ST7 - Process
Design Capacity: 7,500 gallons

Emission Source/Control: 85SWH - Process

Emission Source/Control: 85VCS - Process

Emission Source/Control: 85VP1 - Process

Emission Source/Control: 85VP2 - Process

Item 477.216(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: F-INISH

Process: 176

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #176 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF.

Emission Source/Control: 33SHB - Control
Control Type: FABRIC FILTER

Emission Source/Control: 33DTS - Process

Emission Source/Control: 33ES4 - Process

Emission Source/Control: 33F12 - Process

Emission Source/Control: 33F58 - Process

Emission Source/Control: 33FDF - Process

Emission Source/Control: 33GAP - Process

Emission Source/Control: 33HOF - Process

Emission Source/Control: 33HR1 - Process

Emission Source/Control: 33HR2 - Process

Emission Source/Control: 33LDP - Process

Emission Source/Control: 33ST1 - Process



Emission Source/Control: 33ST2 - Process

Emission Source/Control: 33ST3 - Process

Emission Source/Control: 33ST4 - Process

Emission Source/Control: 33T19 - Process

Emission Source/Control: 33T23 - Process

Emission Source/Control: 33TDS - Process

Emission Source/Control: 33WDD - Process

Emission Source/Control: 33WF1 - Process

Emission Source/Control: 33WF2 - Process

Emission Source/Control: 33WP1 - Process

Emission Source/Control: 33WP2 - Process

Emission Source/Control: 33WP3 - Process

Emission Source/Control: 33WP4 - Process

Emission Source/Control: 33WPF - Process

Emission Source/Control: 33WV1 - Process

Emission Source/Control: 33WV2 - Process

Item 477.217(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: F-INISH

Process: 177

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #177 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Oart 63 Subpart FFFF.

Emission Source/Control: 33SHB - Control

Control Type: FABRIC FILTER

Emission Source/Control: 33DTS - Process

Emission Source/Control: 33ES4 - Process

Emission Source/Control: 33F12 - Process

Emission Source/Control: 33F58 - Process



Emission Source/Control: 33FDF - Process

Emission Source/Control: 33GAP - Process

Emission Source/Control: 33HOF - Process

Emission Source/Control: 33HR1 - Process

Emission Source/Control: 33HR2 - Process

Emission Source/Control: 33LDP - Process

Emission Source/Control: 33SBE - Process

Emission Source/Control: 33ST1 - Process

Emission Source/Control: 33ST2 - Process

Emission Source/Control: 33ST3 - Process

Emission Source/Control: 33ST4 - Process

Emission Source/Control: 33T19 - Process

Emission Source/Control: 33T23 - Process

Emission Source/Control: 33TDS - Process

Emission Source/Control: 33WDD - Process

Emission Source/Control: 33WF1 - Process

Emission Source/Control: 33WF2 - Process

Emission Source/Control: 33WP1 - Process

Emission Source/Control: 33WP2 - Process

Emission Source/Control: 33WP3 - Process

Emission Source/Control: 33WP4 - Process

Emission Source/Control: 33WPF - Process

Emission Source/Control: 33WV1 - Process

Emission Source/Control: 33WV2 - Process

Item 477.218(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: F-INISH

Process: 178

Source Classification Code: 3-01-999-99



Process Description:

Equipment for Family of Material #178 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF.

Emission Source/Control: 33SHB - Control
Control Type: FABRIC FILTER

Emission Source/Control: 33DTS - Process

Emission Source/Control: 33ES4 - Process

Emission Source/Control: 33F12 - Process

Emission Source/Control: 33F58 - Process

Emission Source/Control: 33FDF - Process

Emission Source/Control: 33GAP - Process

Emission Source/Control: 33HOF - Process

Emission Source/Control: 33HR1 - Process

Emission Source/Control: 33HR2 - Process

Emission Source/Control: 33LDP - Process

Emission Source/Control: 33ST1 - Process

Emission Source/Control: 33ST2 - Process

Emission Source/Control: 33ST3 - Process

Emission Source/Control: 33ST4 - Process

Emission Source/Control: 33T19 - Process

Emission Source/Control: 33T23 - Process

Emission Source/Control: 33TDS - Process

Emission Source/Control: 33WDD - Process

Emission Source/Control: 33WF1 - Process

Emission Source/Control: 33WF2 - Process

Emission Source/Control: 33WP1 - Process

Emission Source/Control: 33WP2 - Process

Emission Source/Control: 33WP3 - Process



Emission Source/Control: 33WP4 - Process

Emission Source/Control: 33WPF - Process

Emission Source/Control: 33WV1 - Process

Emission Source/Control: 33WV2 - Process

Item 477.219(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: F-INISH

Process: 179

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #179 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Oart 63 Subpart FFFF.

Emission Source/Control: 33SHB - Control

Control Type: FABRIC FILTER

Emission Source/Control: 33DTS - Process

Emission Source/Control: 33ES4 - Process

Emission Source/Control: 33F12 - Process

Emission Source/Control: 33F58 - Process

Emission Source/Control: 33FDF - Process

Emission Source/Control: 33GAP - Process

Emission Source/Control: 33HOF - Process

Emission Source/Control: 33HR1 - Process

Emission Source/Control: 33HR2 - Process

Emission Source/Control: 33LDP - Process

Emission Source/Control: 33ST1 - Process

Emission Source/Control: 33ST2 - Process

Emission Source/Control: 33ST3 - Process

Emission Source/Control: 33ST4 - Process

Emission Source/Control: 33T19 - Process

Emission Source/Control: 33T23 - Process



Emission Source/Control: 33TDS - Process

Emission Source/Control: 33WDD - Process

Emission Source/Control: 33WF1 - Process

Emission Source/Control: 33WF2 - Process

Emission Source/Control: 33WP1 - Process

Emission Source/Control: 33WP2 - Process

Emission Source/Control: 33WP3 - Process

Emission Source/Control: 33WP4 - Process

Emission Source/Control: 33WPF - Process

Emission Source/Control: 33WV1 - Process

Emission Source/Control: 33WV2 - Process

Item 477.220(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: F-INISH

Process: 180

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #180 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Oart 63 Subpart FFFF.

Emission Source/Control: 78LED - Process

Emission Source/Control: 78NFT - Process

Emission Source/Control: 78SFT - Process

Emission Source/Control: 78TFE - Process

Item 477.221(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: F-INISH

Process: 181

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #181 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Oart 63 Subpart FFFF.

Emission Source/Control: 78LED - Process



Emission Source/Control: 78NFT - Process

Emission Source/Control: 78SFT - Process

Emission Source/Control: 78TFE - Process

Item 477.222(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: F-INISH

Process: 182

Source Classification Code: 3-01-999-99

Process Description:

Equipment for Family of Material #182 which is a miscellaneous organic manufacturing unit (MCPU) that is regulated under 40 CFR Part 63 Subpart FFFF.

Emission Source/Control: 85CV1 - Control

Control Type: GAS SCRUBBER (GENERAL, NOT CLASSIFIED)

Emission Source/Control: 85CV2 - Control

Control Type: GAS SCRUBBER (GENERAL, NOT CLASSIFIED)

Emission Source/Control: 85CV3 - Control

Control Type: CONSERVATION VENT

Emission Source/Control: 85DCS - Control

Control Type: FABRIC FILTER

Emission Source/Control: 85BER - Process

Emission Source/Control: 85CSC - Process

Emission Source/Control: 85CT1 - Process

Emission Source/Control: 85CT3 - Process

Emission Source/Control: 85DRM - Process

Emission Source/Control: 85DUH - Process

Emission Source/Control: 85FPT - Process

Emission Source/Control: 85GC1 - Process

Emission Source/Control: 85GC2 - Process

Emission Source/Control: 85GC3 - Process

Emission Source/Control: 85GC4 - Process

Emission Source/Control: 85GC6 - Process

Emission Source/Control: 85GRV - Process



Emission Source/Control: 85HOP - Process

Emission Source/Control: 85PD0 - Process

Emission Source/Control: 85PD2 - Process

Emission Source/Control: 85PIS - Process

Emission Source/Control: 85SFH - Process

Emission Source/Control: 85ST2 - Process

Emission Source/Control: 85VCS - Process

Emission Source/Control: 85VP1 - Process

Item 477.223(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: F-INISH

Process: 207

Source Classification Code: 3-01-999-99

Process Description:

This process represents the management of Group 1 wastewater in individual drain systems. The Group 1 wastewater streams are generated by the miscellaneous organic chemical manufacturing units (MCPUs) in C-27018 that are regulated under 40 CFR Part 63, Subpart FFFF (Miscellaneous Organic Chemical Manufacturing).

Emission Source/Control: GR1WW - Process

Item 477.224(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: F-INISH

Process: 218

Source Classification Code: 3-01-070-02

Process Description:

01 - catalyst vapors emitted by material in purge drums
waste drums screening operations drum weigh 02 - caco3
&/or tio2 is fed continuously from gravity feeders
898-424-0067 to inlet hopper on 03 - "packaged" piped
vacuum cleaning system (898-451-003) for housekeeping in
processing areas of 04 - vent from the beringer oven

Emission Source/Control: 85BER - Process

Emission Source/Control: 85DRM - Process

Emission Source/Control: 85GRV - Process

Emission Source/Control: 85HOP - Process



Emission Source/Control: 85VCS - Process

Item 477.225(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: F-INISH

Process: 219

Source Classification Code: 3-01-070-02

Process Description:

Untreated filler is conveyed via a moving air stream to this silo displaced air from the silo is filtered and vented to atmosphere

Emission Source/Control: 85SFH - Process

Item 477.226(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: F-INISH

Process: 716

Source Classification Code: 3-01-026-30

Process Description:

Doughmixer area - doughmixers #3,5,6,7,8, and 9 vent to a hood. The doughmixers are batch mixers used in the production of various products.

Emission Source/Control: DMXR3 - Process

Emission Source/Control: DMXR5 - Process

Emission Source/Control: DMXR6 - Process

Emission Source/Control: DMXR7 - Process

Emission Source/Control: DMXR8 - Process

Emission Source/Control: DMXR9 - Process

Item 477.227(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: F-INISH

Process: 729

Source Classification Code: 3-01-026-30

Process Description:

Transfer truck unloading. Tank wagon loading/unloading station.

Emission Source/Control: 71TWL - Process

Item 477.228(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: F-INISH

Process: 734

Source Classification Code: 3-01-026-30

Process Description:



4000 PUFA. This process consists of a 1-Hexene process tank.

Emission Source/Control: 37HEX - Process

Item 477.229(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: F-INISH

Process: 735

Source Classification Code: 3-01-070-02

Process Description:

East and West Systems - Standing losses from atmospheric storage tanks. The tanks are used to store Acetyl Chloride waste, Silane blend, and propyltriacetoxysilane (PTAS).

Emission Source/Control: 76VS1 - Process

Emission Source/Control: 76VS2 - Process

Emission Source/Control: 76VS3 - Process

Item 477.230(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: F-INISH

Process: 736

Source Classification Code: 3-01-070-02

Process Description:

East and West Systems - Working losses from atmospheric storage tanks. The tanks are used to store Acetyl Chloride waste, Silane blend, and propyltriacetoxysilane (PTAS).

Emission Source/Control: 76VS1 - Process

Emission Source/Control: 76VS2 - Process

Emission Source/Control: 76VS3 - Process

Item 477.231(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: F-INISH

Process: 738

Source Classification Code: 3-99-999-94

Process Description:

Working losses from the four pigment tanks are used to store liquid pigment dispersions. The vessels vent to the atmosphere when the vessels are charged from the drums the vessels vent to a common conservation vent header.

Emission Source/Control: 85FPT - Process

Item 477.232(From Mod 0):



This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: F-INISH

Process: 739

Source Classification Code: 3-99-999-94

Process Description:

Standing storage losses from four pigment tanks are used to store liquid pigment dispersions. The vessels vent to the atmosphere when the vessels are charged from the drums. The vessels vent to a common conservation vent header.

Emission Source/Control: 85FPT - Process

Item 477.233(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: F-INISH

Process: 740

Source Classification Code: 3-01-070-02

Process Description:

WP2, WP3 Tanks - This process represents working losses from volatile organic liquid storage tanks used in the WP-2 and WP-3 operations. Tanks are under pressure or have a Nitrogen blanket.

Emission Source/Control: 85PT1 - Process

Emission Source/Control: 85PT2 - Process

Emission Source/Control: 85PT3 - Process

Emission Source/Control: 85PT4 - Process

Item 477.234(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: F-INISH

Process: BMD

Source Classification Code: 3-01-026-99

Process Description:

Molding Compound Area Solids handling operations, including dust collectors for grinding operations and exhaust hoods, blending and extruding, and bag slitting. Associated equipment includes mixers, extruders, grinders, and blenders.

Emission Source/Control: DS2C1 - Control
Control Type: FABRIC FILTER

Emission Source/Control: DS3C1 - Control
Control Type: FABRIC FILTER

Emission Source/Control: DS201 - Process

Emission Source/Control: DS301 - Process



Item 477.235(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: F-INISH
Process: DEG Source Classification Code: 4-01-002-99
Process Description:
Maintenance shops - Cold cleaning solvent degreasing units that use a petroleum distillate solvent.

Emission Source/Control: 97DEG - Process

Emission Source/Control: BA101 - Process

Emission Source/Control: CV201 - Process

Emission Source/Control: CY101 - Process

Emission Source/Control: CY201 - Process

Emission Source/Control: HT401 - Process

Emission Source/Control: HT901 - Process

Emission Source/Control: ID301 - Process

Item 477.236(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: F-INISH
Process: FFR Source Classification Code: 3-01-018-47
Process Description:
Eductor system. Insignificant emissions from the Phenyl Tetramer eductor system.

Emission Source/Control: 37PTE - Process

Item 477.237(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: F-INISH
Process: TKC Source Classification Code: 4-07-999-98
Process Description:
Transfer and Blending. Working losses from Tank 538. The tank is under a Nitrogen pad/dapad system.

Emission Source/Control: 23SSS - Process

Item 477.238(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: F-INISH
Process: TKD Source Classification Code: 4-07-999-97



Process Description:

Transfer and Blending. Working losses from Isopropanol storage tank.

Emission Source/Control: 23IST - Process

Item 477.239(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: F-INISH

Process: TKE

Source Classification Code: 4-07-999-97

Process Description:

Transfer and Blending. Standing storage losses from Isopropanol storage tank.

Emission Source/Control: 23IST - Process

Item 477.240(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: F-INISH

Process: WPF

Source Classification Code: 4-90-002-06

Process Description: Fugitive emissions WP1, & WP4.

Emission Source/Control: CY102 - Process

Item 477.241(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: T-13004

Process: 742

Source Classification Code: 3-99-999-94

Process Description:

Process development. Emissions from siloxanes passing from the compounder to the LIM after-condenser at location 4A.

Emission Source/Control: 13VR1 - Control

Control Type: VAPOR RECOVERY SYS(INCL.

CONDENSERS,HOODING, OTHER ENCLOSURES)

Emission Source/Control: 13HCE - Process

Item 477.242(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: T-13004

Process: 743

Source Classification Code: 3-99-999-94

Process Description:

Process development. Volatiles stripped from the LIM during compounding and cooling pass through the shared LIM after-condenser at location 4C.

Emission Source/Control: 13VR3 - Control



Control Type: VAPOR RECOVERY SYS(INCL.
CONDENSERS,HOODING, OTHER ENCLOSURES)

Emission Source/Control: 13LIM - Process

Item 477.243(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: U-28002
Process: 408 Source Classification Code: 1-02-006-01
Process Description: Boiler 13 - Natural gas combustion.

Emission Source/Control: BLR13 - Combustion

Emission Source/Control: 13LNB - Control
Control Type: DRY LOW NO_x BURNER

Item 477.244(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: U-28002
Process: 409 Source Classification Code: 1-02-004-01
Process Description: Boiler 13 - Number 6 fuel oil combustion.

Emission Source/Control: BLR13 - Combustion

Emission Source/Control: 13LNB - Control
Control Type: DRY LOW NO_x BURNER

Item 477.245(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: U-28003
Process: 412 Source Classification Code: 1-02-004-01
Process Description: Boilers 15 - number 6 fuel oil combustion.

Emission Source/Control: BLR15 - Combustion

Emission Source/Control: 15LNB - Control
Control Type: DRY LOW NO_x BURNER

Item 477.246(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: U-28003
Process: 413 Source Classification Code: 1-02-006-01
Process Description: Boiler 15 - Natural gas combustion.

Emission Source/Control: BLR15 - Combustion

Emission Source/Control: 15LNB - Control
Control Type: DRY LOW NO_x BURNER



Item 477.247(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: U-28003
Process: 414 Source Classification Code: 1-02-004-01
Process Description: Boiler 14 - Number 6 fuel oil combustion.

Emission Source/Control: BLR14 - Combustion

Emission Source/Control: 14LNB - Control
Control Type: DRY LOW NO_x BURNER

Item 477.248(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: U-28003
Process: 415 Source Classification Code: 1-02-006-01
Process Description: Boiler 14 - Natural gas combustion.

Emission Source/Control: BLR14 - Combustion

Emission Source/Control: 14LNB - Control
Control Type: DRY LOW NO_x BURNER

Item 477.249(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: U-28003
Process: 416 Source Classification Code: 1-02-006-02
Process Description: Boiler 17 - Natural gas combustion.

Emission Source/Control: BLR16 - Combustion

Item 477.250(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: U-28003
Process: 417 Source Classification Code: 1-02-006-02
Process Description: Boiler 16 - Natural gas combustion.

Emission Source/Control: BLR17 - Combustion

Item 477.251(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: W-97004
Process: 744 Source Classification Code: 3-01-070-02
Process Description:
Underground storage tanks receiving acidic aqueous polar
and non-polar solvent containing wastewater via sewer
pipe.

Emission Source/Control: 97UV1 - Control



Control Type: CONSERVATION VENT

Emission Source/Control: 97UV2 - Control
Control Type: CONSERVATION VENT

Emission Source/Control: 9728A - Process

Emission Source/Control: 9728B - Process

Item 477.252(From Mod 0):

This permit authorizes the following regulated processes for the cited Emission Unit:

Emission Unit: W-97004

Process: 745

Source Classification Code: 5-03-007-01

Process Description:

Waste Water Treatment Plant - 5,000 gallon neutralization tank which receives non-aqueous phase material and neutralizes it with KOH.

Emission Source/Control: 97NTV - Control

Control Type: CONSERVATION VENT

Emission Source/Control: 97NTK - Process

**Condition 1-51: General standards - identification of equipment
Effective for entire length of Permit**

Applicable Federal Requirement:40CFR 63.162(c), Subpart H

Item 1-51.1:

This Condition applies to Emission Unit: C-27018

Process: 400

Emission Source:

FUGTV

Item 1-51.2:

Each piece of equipment to which Subpart H applies shall be identified such that it can be distinguished readily from equipment that is not subject to Subpart H. This does not require physical tagging, but may be identified on a plant site plan, log entries, or by designation of process unit boundaries by some form of weatherproof identification.

**Condition 1-52: Delay of repair provisions for heat exchange systems
Effective for entire length of Permit**

Applicable Federal Requirement:40CFR 63.104, Subpart F

Item 1-52.1:

This Condition applies to Emission Unit: C-27018

Process: 406

Emission Source:

HXCWW

Item 1-52.2:

Delay of repair is allowed for heat exchanger system leaks in the following situations:



- 1) If the equipment that is isolated from the process, or
- 2) If the repair is technically infeasible without a shutdown, and one of the following is true:
 - a) A shutdown is expected within two months after the delay of repair is determined to be necessary. Repair may be delayed until that shutdown.
 - b) A shutdown is not expected within the next two months and a shutdown to repair the leaking equipment would result in greater emissions than delaying repair. In this case the owner/operator shall document the items listed in 63.104(e)(2)(i)(A) and (B) and delay the repair until the next shutdown.
 - c) A shutdown is not expected within the next two months and the owner/operator does not determine that the shutdown would result in greater emissions than a delay of repair. The owner/operator may delay the repair for 120 days. The owner/operator shall demonstrate that the necessary parts or personnel were not available

The owner/operator shall submit the following in the next semiannual report:

- 1) the presence of a leak and the date the leak was detected
- 2) whether the leak has been repaired
- 3) the reason(s) for the delay of repair
- 4) the expected date of repair if not repaired
- 5) the date of successful repair of the leak

Condition 1-53: Provisions for handling leaks found in heat exchanger coolant

Effective for entire length of Permit

Applicable Federal Requirement: 40CFR 63.104, Subpart F

Item 1-53.1:

This Condition applies to Emission Unit: C-27018

Process: 406

Emission Source:

HXCWW

Item 1-53.2:

If a leak is detected, it shall be repaired as soon as practical but not later than 45 calendar days after the owner/operator is notified of the results indicating a leak. The owner/operator shall confirm the repair within 7 days of the repair or startup, whichever is later.

The owner/operator shall retain the following records:

- records of any leaks detected
- monitoring data indicating the presence of a leak
- date(s) of the leak's detection
- date(s) of efforts to repair leak(s)
- method and date of confirmation of leak(s)



STATE ONLY ENFORCEABLE CONDITIONS

****** Facility Level ******

NOTIFICATION OF GENERAL PERMITTEE OBLIGATIONS

This section contains terms and conditions which are not federally enforceable. Permittees may also have other obligations under regulations of general applicability

Item A: General Provisions for State Enforceable Permit Terms and Condition - 6 NYCRR Part 201-5

Any person who owns and/or operates stationary sources shall operate and maintain all emission units and any required emission control devices in compliance with all applicable Parts of this Chapter and existing laws, and shall operate the facility in accordance with all criteria, emission limits, terms, conditions, and standards in this permit. Failure of such person to properly operate and maintain the effectiveness of such emission units and emission control devices may be sufficient reason for the Department to revoke or deny a permit.

The owner or operator of the permitted facility must maintain all required records on-site for a period of five years and make them available to representatives of the Department upon request. Department representatives must be granted access to any facility regulated by this Subpart, during normal operating hours, for the purpose of determining compliance with this and any other state and federal air pollution control requirements, regulations or law.

STATE ONLY APPLICABLE REQUIREMENTS

The following conditions are state applicable requirements and are not subject to compliance certification requirements unless otherwise noted or required under 6 NYCRR Part 201.

Condition 479: Contaminant List
Effective between the dates of 01/07/2008 and Permit Expiration Date

Applicable State Requirement:ECL 19-0301

Item 479.1:

Emissions of the following contaminants are subject to contaminant specific requirements in this permit(emission limits, control requirements or compliance monitoring conditions).

CAS No: 000064-17-5
Name: ETHYL ALCOHOL (ETHANOL)

CAS No: 000064-19-7



Name: ACETIC ACID

CAS No: 000067-56-1

Name: METHYL ALCOHOL

CAS No: 000067-63-0

Name: ISOPROPYL ALCOHOL

CAS No: 000067-64-1

Name: DIMETHYL KETONE

CAS No: 000074-87-3

Name: METHYL CHLORIDE

CAS No: 000075-36-5

Name: ACETYL CHLORIDE

CAS No: 000075-65-0

Name: 2-METHYL-2-PROPANOL

CAS No: 000075-78-5

Name: DIMETHYLDICHLOROSILANE

CAS No: 000075-79-6

Name: METHYLTRICHLOROSILANE

CAS No: 000075-94-5

Name: SILANE, TRICHLOROETHENYL

CAS No: 000100-41-4

Name: ETHYLBENZENE

CAS No: 000107-46-0

Name: HEXAMETHYLDISILOXANE

CAS No: 000108-88-3

Name: TOLUENE

CAS No: 000124-70-9

Name: SILANE, DICHLOROETHENYLMETHYL

CAS No: 000541-05-9

Name: HEXAMETHYLCYCLOTTRISILOXANE

CAS No: 000556-67-2

Name: OCTAMETHYLCYCLOTETRA SILOXANE

CAS No: 000630-08-0

Name: CARBON MONOXIDE

CAS No: 001066-35-9

Name: SILANE,CHLORODIMETHYL



CAS No: 001112-39-6
Name: SILANE, DIMETHOXYDIMETHYL

CAS No: 001185-55-3
Name: METHYLTRIMETHOXY SILANE

CAS No: 001330-20-7
Name: XYLENE, M, O & P MIXT.

CAS No: 001719-58-0
Name: SILANE, CHLOROETHENYLDIMETHYL

CAS No: 007439-92-1
Name: LEAD

CAS No: 007439-97-6
Name: MERCURY

CAS No: 007440-38-2
Name: ARSENIC

CAS No: 007440-41-7
Name: BERYLLIUM

CAS No: 007440-43-9
Name: CADMIUM

CAS No: 007440-47-3
Name: CHROMIUM

CAS No: 007446-09-5
Name: SULFUR DIOXIDE

CAS No: 007647-01-0
Name: HYDROGEN CHLORIDE

CAS No: 007664-41-7
Name: AMMONIA

CAS No: 007782-50-5
Name: CHLORINE

CAS No: 010026-04-7
Name: TETRACHLORO SILANE

CAS No: 016887-00-6
Name: CHLORIDE ION CL-

CAS No: 022431-89-6
Name: DIOXANE,1,2- 3,3,6,6-TETRAMETHYL

CAS No: 063148-62-9
Name: SILOXANES AND SILICONES,DI-ME



CAS No: 068479-14-1
Name: SILANE, CHLORO METHYL DERIVS

CAS No: 0NY075-00-0
Name: PARTICULATES

CAS No: 0NY075-00-5
Name: PM-10

CAS No: 0NY100-00-0
Name: HAP

CAS No: 0NY210-00-0
Name: OXIDES OF NITROGEN

CAS No: 0NY502-00-0
Name: 40 CFR 60-63 - TOTAL ORGANIC COMPOUNDS (TOC)

CAS No: 0NY998-00-0
Name: VOC

Condition 484: Compliance Demonstration
Effective between the dates of 01/07/2008 and Permit Expiration Date

Applicable State Requirement:

Expired by Mod 1

Item 484.1:

The Compliance Demonstration activity will be performed for the facility:
The Compliance Demonstration applies to:

Emission Unit: F-INISH

Emission Point: 76006

Regulated Contaminant(s):

CAS No: 000067-56-1	METHYL ALCOHOL
CAS No: 000075-36-5	ACETYL CHLORIDE
CAS No: 007647-01-0	HYDROGEN CHLORIDE
CAS No: 068479-14-1	SILANE, CHLORO METHYL DERIVS
CAS No: 000064-19-7	ACETIC ACID

Item 484.2:

Compliance Demonstration shall include the following monitoring:

Monitoring Type: MONITORING OF PROCESS OR CONTROL
DEVICE PARAMETERS AS SURROGATE

Monitoring Description:

Water flow to the second stage of the scrubber will be monitored to ensure sufficient control efficiency. The lower limit of monitoring ensures compliance with all process batch operations. Engineering calculations will be used as evidence of compliance with contaminant control efficiency when the measured flow rate falls below the



lower limit of monitoring.

Parameter Monitored: VOLUMETRIC FLOW RATE

Lower Permit Limit: 6.9 gallons per minute

Monitoring Frequency: CONTINUOUS

Averaging Method: 24-HOUR AVERAGE

Reporting Requirements: SEMI-ANNUALLY (CALENDAR)

Reports due 30 days after the reporting period.

The initial report is due 7/30/2008.

Subsequent reports are due every 6 calendar month(s).

Condition 486: Compliance Demonstration

Effective between the dates of 01/07/2008 and Permit Expiration Date

Applicable State Requirement:

Expired by Mod 1

Item 486.1:

The Compliance Demonstration activity will be performed for the facility:

The Compliance Demonstration applies to:

Emission Unit: F-INISH

Emission Point: 76006

Regulated Contaminant(s):

CAS No: 000067-56-1

METHYL ALCOHOL

CAS No: 000075-36-5

ACETYL CHLORIDE

CAS No: 007647-01-0

HYDROGEN CHLORIDE

CAS No: 068479-14-1

SILANE, CHLORO METHYL DERIVS

CAS No: 000064-19-7

ACETIC ACID

Item 486.2:

Compliance Demonstration shall include the following monitoring:

Monitoring Type: MONITORING OF PROCESS OR CONTROL
DEVICE PARAMETERS AS SURROGATE

Monitoring Description:

Water flow to the first stage of the scrubber will be monitored to ensure sufficient control efficiency. The lower limit of monitoring ensures compliance with all process batch operations. Engineering calculations will be used as evidence of compliance with contaminant control efficiency when the measured flow rate falls below the lower limit of monitoring.

Parameter Monitored: VOLUMETRIC FLOW RATE

Lower Permit Limit: 19.4 gallons per minute

Monitoring Frequency: CONTINUOUS

Averaging Method: 24-HOUR AVERAGE

Reporting Requirements: SEMI-ANNUALLY (CALENDAR)

Reports due 30 days after the reporting period.

The initial report is due 7/30/2008.

Subsequent reports are due every 6 calendar month(s).



Condition 493: Compliance Demonstration
Effective between the dates of 01/07/2008 and Permit Expiration Date

Applicable State Requirement:

Expired by Mod 1

Item 493.1:

The Compliance Demonstration activity will be performed for the facility:
The Compliance Demonstration applies to:

Emission Unit: C-27018 Emission Point: 62007

Regulated Contaminant(s):
CAS No: 007647-01-0 HYDROGEN CHLORIDE

Item 493.2:

Compliance Demonstration shall include the following monitoring:

Monitoring Type: MONITORING OF PROCESS OR CONTROL
DEVICE PARAMETERS AS SURROGATE

Monitoring Description:

The scrubber water flow (ES-MCSVS) is monitored to ensure sufficient control efficiency. Engineering calculations will be used as evidence of compliance with control efficiency when the measured flow rate falls below the lower limit of monitoring.

Parameter Monitored: VOLUMETRIC FLOW RATE

Lower Permit Limit: 100 gallons per minute

Monitoring Frequency: CONTINUOUS

Averaging Method: 24-HOUR AVERAGE

Reporting Requirements: SEMI-ANNUALLY (CALENDAR)

Reports due 30 days after the reporting period.

The initial report is due 7/30/2008.

Subsequent reports are due every 6 calendar month(s).

Condition 494: Compliance Demonstration
Effective between the dates of 01/07/2008 and Permit Expiration Date

Applicable State Requirement:

Expired by Mod 1

Item 494.1:

The Compliance Demonstration activity will be performed for the facility:
The Compliance Demonstration applies to:

Emission Unit: C-27018 Emission Point: 27024

Regulated Contaminant(s):
CAS No: 007647-01-0 HYDROGEN CHLORIDE

Item 494.2:

Compliance Demonstration shall include the following monitoring:



Monitoring Type: MONITORING OF PROCESS OR CONTROL
DEVICE PARAMETERS AS SURROGATE

Monitoring Description:

The scrubber temperature will be monitored to ensure the scrubber is operating at the required control efficiency. Engineering calculations will be used as evidence of compliance with control efficiency when the measured parameter exceeds the upper limit of monitoring.

Parameter Monitored: TEMPERATURE

Upper Permit Limit: 95 degrees C below the approved
performance test combustion
temperature

Monitoring Frequency: CONTINUOUS

Averaging Method: 24-HOUR AVERAGE

Reporting Requirements: SEMI-ANNUALLY (CALENDAR)

Reports due 30 days after the reporting period.

The initial report is due 7/30/2008.

Subsequent reports are due every 6 calendar month(s).

Condition 495: Compliance Demonstration
Effective between the dates of 01/07/2008 and Permit Expiration Date

Applicable State Requirement:

Expired by Mod 1

Item 495.1:

The Compliance Demonstration activity will be performed for the facility:

The Compliance Demonstration applies to:

Emission Unit: C-27035

Emission Point: 27035

Regulated Contaminant(s):

CAS No: 007647-01-0

HYDROGEN CHLORIDE

Item 495.2:

Compliance Demonstration shall include the following monitoring:

Monitoring Type: MONITORING OF PROCESS OR CONTROL
DEVICE PARAMETERS AS SURROGATE

Monitoring Description:

The packed tower water scrubber flow is maintained at a minimum of 5 gpm to ensure 99% control efficiency for Part 212. Engineering calculations will be used as evidence of compliance with control efficiency when the measured flow rate falls below the lower limit of monitoring.

Parameter Monitored: VOLUMETRIC FLOW RATE

Lower Permit Limit: 5 gallons per minute

Monitoring Frequency: CONTINUOUS

Averaging Method: 24-HOUR AVERAGE

Reporting Requirements: SEMI-ANNUALLY (CALENDAR)



Reports due 30 days after the reporting period.
The initial report is due 7/30/2008.
Subsequent reports are due every 6 calendar month(s).

Condition 496: Compliance Demonstration
Effective between the dates of 01/07/2008 and Permit Expiration Date

Applicable State Requirement:

Expired by Mod 1

Item 496.1:

The Compliance Demonstration activity will be performed for the facility:
The Compliance Demonstration applies to:

Emission Unit: F-INISH

Emission Point: 76006

Regulated Contaminant(s):

CAS No: 000064-19-7	ACETIC ACID
CAS No: 000067-56-1	METHYL ALCOHOL
CAS No: 000075-36-5	ACETYL CHLORIDE
CAS No: 007647-01-0	HYDROGEN CHLORIDE
CAS No: 068479-14-1	SILANE, CHLORO METHYL DERIVS

Item 496.2:

Compliance Demonstration shall include the following monitoring:

Monitoring Type: MONITORING OF PROCESS OR CONTROL
DEVICE PARAMETERS AS SURROGATE

Monitoring Description:

Spray tower flow rate will be monitored to ensure sufficient control efficiency. The lower limit of monitoring ensures compliance with all process batch operations. Engineering calculations will be used as evidence of compliance with contaminant control efficiency when the measured flow rate falls below the lower limit of monitoring.

Parameter Monitored: VOLUMETRIC FLOW RATE

Lower Permit Limit: 13.4 gallons per minute

Monitoring Frequency: CONTINUOUS

Averaging Method: 24-HOUR AVERAGE

Reporting Requirements: SEMI-ANNUALLY (CALENDAR)

Reports due 30 days after the reporting period.

The initial report is due 7/30/2008.

Subsequent reports are due every 6 calendar month(s).

Condition 501: Compliance Demonstration
Effective between the dates of 01/07/2008 and Permit Expiration Date

Applicable State Requirement:

Expired by Mod 1

Item 501.1:



The Compliance Demonstration activity will be performed for the facility:

The Compliance Demonstration applies to:

Emission Unit: C-27018

Emission Point: 35017

Regulated Contaminant(s):

CAS No: 000556-67-2

OCTAMETHYLCYCLOTETRA SILOXANE

Item 501.2:

Compliance Demonstration shall include the following monitoring:

Monitoring Type: MONITORING OF PROCESS OR CONTROL
DEVICE PARAMETERS AS SURROGATE

Monitoring Description:

The water flow to the scrubber is monitored to ensure the scrubber is operating at the required control efficiency. Engineering calculations will be used as evidence of compliance with control efficiency when the measured flow rate falls below the lower limit of monitoring.

Parameter Monitored: VOLUMETRIC FLOW RATE

Lower Permit Limit: 1.5 gallons per minute

Monitoring Frequency: PER SHIFT

Averaging Method: 24-HOUR AVERAGE

Reporting Requirements: SEMI-ANNUALLY (CALENDAR)

Reports due 30 days after the reporting period.

The initial report is due 7/30/2008.

Subsequent reports are due every 6 calendar month(s).

Condition 504: Compliance Demonstration

Effective between the dates of 01/07/2008 and Permit Expiration Date

Applicable State Requirement:

Expired by Mod 1

Item 504.1:

The Compliance Demonstration activity will be performed for the facility:

The Compliance Demonstration applies to:

Emission Unit: C-27018

Emission Point: 76710

Emission Unit: C-27018

Emission Point: 76711

Regulated Contaminant(s):

CAS No: 000067-56-1

METHYL ALCOHOL

CAS No: 000075-36-5

ACETYL CHLORIDE

CAS No: 000075-65-0

2-METHYL-2-PROPANOL

CAS No: 001112-39-6

SILANE, DIMETHOXYDIMETHYL

CAS No: 007647-01-0

HYDROGEN CHLORIDE

CAS No: 000067-64-1

DIMETHYL KETONE

Item 504.2:

Compliance Demonstration shall include the following monitoring:



Monitoring Type: MONITORING OF PROCESS OR CONTROL
DEVICE PARAMETERS AS SURROGATE

Monitoring Description:

High acid scrubber water flow will be monitored to ensure sufficient control efficiency. The lower limit of monitoring ensures compliance with all process batch operations. Engineering calculations will be used as evidence of compliance with contaminant control efficiency when the measured flow rate falls below the lower limit of monitoring.

Parameter Monitored: VOLUMETRIC FLOW RATE

Lower Permit Limit: 40 gallons per minute

Monitoring Frequency: PER BATCH OF PRODUCT/RAW MATERIAL
CHANGE

Averaging Method: MINIMUM - NOT TO FALL BELOW STATED
VALUE AT ANY TIME

Reporting Requirements: SEMI-ANNUALLY (CALENDAR)

Reports due 30 days after the reporting period.

The initial report is due 7/30/2008.

Subsequent reports are due every 6 calendar month(s).

Condition 506: Compliance Demonstration
Effective between the dates of 01/07/2008 and Permit Expiration Date

Applicable State Requirement:

Expired by Mod 1

Item 506.1:

The Compliance Demonstration activity will be performed for the facility:

The Compliance Demonstration applies to:

Emission Unit: F-INISH

Emission Point: 76006

Regulated Contaminant(s):

CAS No: 000067-56-1

METHYL ALCOHOL

CAS No: 000075-36-5

ACETYL CHLORIDE

CAS No: 007647-01-0

HYDROGEN CHLORIDE

CAS No: 068479-14-1

SILANE, CHLORO METHYL DERIVS

CAS No: 000064-19-7

ACETIC ACID

Item 506.2:

Compliance Demonstration shall include the following monitoring:

Monitoring Type: MONITORING OF PROCESS OR CONTROL
DEVICE PARAMETERS AS SURROGATE

Monitoring Description:

Water flow to the third stage of the scrubber will be monitored to ensure sufficient control efficiency. The lower limit of monitoring ensures compliance with all process batch operations. Engineering calculations will be used as evidence of compliance with contaminant control



efficiency when the measured flow rate falls below the lower limit of monitoring.

Parameter Monitored: VOLUMETRIC FLOW RATE

Lower Permit Limit: 6.0 gallons per minute

Monitoring Frequency: CONTINUOUS

Averaging Method: 24-HOUR AVERAGE

Reporting Requirements: SEMI-ANNUALLY (CALENDAR)

Reports due 30 days after the reporting period.

The initial report is due 7/30/2008.

Subsequent reports are due every 6 calendar month(s).

Condition 509: Compliance Demonstration
Effective between the dates of 01/07/2008 and Permit Expiration Date

Applicable State Requirement:

Expired by Mod 1

Item 509.1:

The Compliance Demonstration activity will be performed for the facility:

The Compliance Demonstration applies to:

Emission Unit: C-27018

Emission Point: 76001

Regulated Contaminant(s):

CAS No: 000067-56-1	METHYL ALCOHOL
CAS No: 000067-64-1	DIMETHYL KETONE
CAS No: 000075-36-5	ACETYL CHLORIDE
CAS No: 000075-78-5	DIMETHYLDICHLOROSILANE
CAS No: 000075-79-6	METHYLTRICHLOROSILANE
CAS No: 000107-46-0	HEXAMETHYLDISILOXANE
CAS No: 000108-88-3	TOLUENE
CAS No: 000124-70-9	SILANE, DICHLOROETHENYLMETHYL
CAS No: 000556-67-2	OCTAMETHYLCYCLOTETRA SILOXANE
CAS No: 001112-39-6	SILANE, DIMETHOXYDIMETHYL
CAS No: 001185-55-3	METHYLTRIMETHOXY-SILANE
CAS No: 001719-58-0	SILANE, CHLOROETHENYLDIMETHYL
CAS No: 007647-01-0	HYDROGEN CHLORIDE
CAS No: 010026-04-7	TETRACHLORO SILANE
CAS No: 068479-14-1	SILANE, CHLORO METHYL DERIVS
CAS No: 000064-19-7	ACETIC ACID

Item 509.2:

Compliance Demonstration shall include the following monitoring:

Monitoring Type: MONITORING OF PROCESS OR CONTROL
DEVICE PARAMETERS AS SURROGATE

Monitoring Description:

A flow meter is used to monitor the water flow rate to the scrubber to ensure sufficient control efficiency. Engineering calculations will be used as evidence of compliance with control efficiency when the measured flow rate falls below the lower limit of monitoring.



Parameter Monitored: VOLUMETRIC FLOW RATE

Lower Permit Limit: 72 gallons per minute

Monitoring Frequency: DAILY

Averaging Method: MINIMUM - NOT TO FALL BELOW STATED
VALUE AT ANY TIME

Reporting Requirements: SEMI-ANNUALLY (CALENDAR)

Reports due 30 days after the reporting period.

The initial report is due 7/30/2008.

Subsequent reports are due every 6 calendar month(s).

